

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION
NOTICE OF PERMIT

In the matter of an
Application for Permit by:

Mr. John R. Steiner
Director of Facilities and Environmental Affairs
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32902-0883


DER File Nos. AC 05-202415
AC 05-203985
AC 05-205848
AC 05-205849
Brevard County

Enclosed are Permit Numbers AC 05-202415, -203985, -205848, and -205849 to modify Buildings 54, 55, 57 and 59 at the Harris Semiconductor facility in Palm Bay, Brevard County, Florida. These permits are issued pursuant to Section(s) 403, Florida Statutes.

Any party to this Order (permit) has the right to seek judicial review of the permits pursuant to Section 120.68, Florida Statutes, by the filing of a Notice of Appeal pursuant to Rule 9.110, Florida Rules of Appellate Procedure, with the Clerk of the Department in the Office of General Counsel, 2600 Blair Stone Road, Tallahassee, Florida 32399-2400; and by filing a copy of the Notice of Appeal accompanied by the applicable filing fees with the appropriate District Court of Appeal. The Notice of Appeal must be filed within 30 days from the date this Notice is filed with the Clerk of the Department.

Executed in Tallahassee, Florida.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

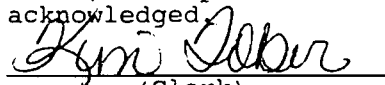

C. H. Fancy, P.E., Chief
Bureau of Air Regulation
2600 Blair Stone Road
Tallahassee, FL 32399-2400
904-488-1344

CERTIFICATE OF SERVICE

The undersigned duly designated deputy agency clerk hereby certifies that this NOTICE OF PERMIT and all copies were mailed before the close of business on 2/18/92 to the listed persons.

Clerk Stamp

FILING AND ACKNOWLEDGMENT FILED,
on this date, pursuant to
§120.52(11), Florida Statutes,
with the designated Department
Clerk, receipt of which is hereby
acknowledged.


(Clerk)

2/18/92
(Date)

Copies furnished to:

C. Collins, Central District
C. Triantafyllidis, HS
S. McClarty, P.E., HS

Final Determination

Harris Semiconductor
Brevard County
City of Palm Bay, Florida

Construction Permit Nos.

AC 05-202415
AC 05-203985
AC 05-205848
AC 05-205849

Department of Environmental Regulation
Division of Air Resources Management
Bureau of Air Regulation

February 14, 1992

Final Determination

The construction permit application packages have been reviewed by the Department. Public Notice of the Department's Intent to Issue was published in The Tribune on January 21, 1992. The Technical Evaluation and Preliminary Determination was distributed on January 10, 1992, and available for public inspection at the Department's Central District office and the Department's Bureau of Air Regulation office.

A comment was received via a telephone call from Mr. Constantine Triantafyllidis (Harris Semiconductor) during the public notice period. He noted a typographical error in the VOC allowable emissions for the source/Building 57 in permit No. AC 05-205848, Specific Condition #1, which should have read 3.0 TPY instead of 2.0 TPY. The error has been corrected. Therefore, it is recommended that the construction permits be issued as drafted and as corrected.



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-203985
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 54 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 54, which is an existing source that utilizes hood type work stations for the manufacture of semiconductors, to permit a decrease in the potential acid and the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control systems are:

- o F54S01: a Beverly Pacific 50,000 scfm (43,141 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. PS-50HT;
- o F54S02: a Harrington 17,000 scfm (16,000 acfm) horizontal cross-flow wet scrubber, using PVC packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. ECH 66-9PBS; and,
- o F54S03: a Beverly Pacific 30,000 scfm (29,000 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. PS-24HT.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36
o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent
Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;

b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,

c. Records of monitoring information shall include:

- the date, exact place, and time of sampling or measurements;
- the person responsible for performing the sampling or measurements;
- the dates analyses were performed;
- the person responsible for performing the analyses;
- the analytical techniques or methods used; and,
- the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 54 is 73.8 tons per year.

2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.

3. Continuous operation shall be allowed (i.e., 8760 hours per year).

4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).

5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.

6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 54.

7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
- b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
- d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 54.
9. The source/Building No. 54 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 9.7 TPY.
11. Building No. 54 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

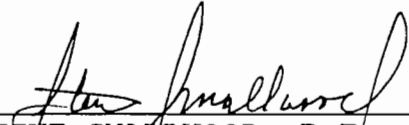
PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this 17th day
of February, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION



STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-202415
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 55 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 55, which is an existing source for the collection, short term storage, and shipping point for waste chemicals from the facility, to permit an increase in the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control system is:

- o F55S01: a Tri-Mer Corp. 9,500 scfm (7,500 acfm) horizontal counter-flow wet scrubber, using a polypropylene filter pack, and with a mist eliminator, for VOC and acid vapor removal; Model No. F/W 3.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36
o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent
Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

- a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;
- b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the dates analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and,
 - the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 55 is 1.0 tons per year.
2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.
3. Continuous operation shall be allowed (i.e., 8760 hours per year).
4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).
5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.
6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 55.
7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:
 - a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
 - b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
 - c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
 - d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 55.
9. The source/Building No. 55 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 0.1 TPY.
11. Building No. 55 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).


PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this 17th day
of February, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION



STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-205848
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 57 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 57, which is an existing source whose primary manufacturing operations are soldering and plating of integrated circuit parts, to permit an increase in the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control system is:

- o F57S01: a Tri-Mer Corp. 13,500 scfm (9,328 acfm) horizontal counter-flow wet scrubber, using a polypropylene filter pack, and with a mist eliminator, for VOC and acid vapor removal; Model No. F/W 5.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36
o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent
Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;

b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,

c. Records of monitoring information shall include:

- the date, exact place, and time of sampling or measurements;
- the person responsible for performing the sampling or measurements;
- the dates analyses were performed;
- the person responsible for performing the analyses;
- the analytical techniques or methods used; and,
- the results of such analyses.

4125. 41455
425-4455

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 57 is 3.0 tons per year.

2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.

3. Continuous operation shall be allowed (i.e., 8760 hours per year).

4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).

5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.

6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 57.

7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
- b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
- d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 57.
9. The source/Building No. 57 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 0.2 TPY.
11. Building No. 57 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

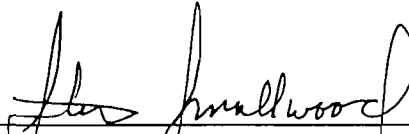
PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

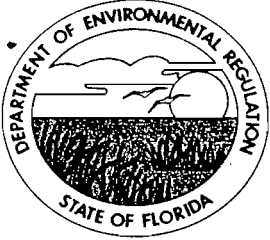
SPECIFIC CONDITIONS:

Issued this 17th day
of February, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION



STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-205849
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 59 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 59, which is an existing source used for the manufacture of semiconductors, to permit an increase in the potential acid emissions. The scrubber control and exhaust systems are:

Reliability Shop:

- o F59S01: a Beverly Pacific 40,000 scfm (30,838 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator for acid vapor removal; Model No. PS-40HT;
- o F59S02: a Beverly Pacific 20,000 scfm (10,972 acfm) vertical counter-current wet scrubber, using polypropylene packing, with a PVC mist eliminator, for VOC (volatile organic compounds/organic solvents) vapor removal; Model No. PS-24VT; and,

Probe Card Repair Shop:

- o F59E04: an exhaust fan.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36

- o Cold Solvent Cleaning/ Stripping 4-01-003-99 Tons VOC/solvent Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;

b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,

c. Records of monitoring information shall include:

- the date, exact place, and time of sampling or measurements;
- the person responsible for performing the sampling or measurements;
- the dates analyses were performed;
- the person responsible for performing the analyses;
- the analytical techniques or methods used; and,
- the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 59 is 8.4 tons per year.

2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.

3. Continuous operation shall be allowed (i.e., 8760 hours per year).

4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).

5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.

6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 59.

7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
- b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
- d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 59.
9. The source/Building No. 59 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 0.3 TPY.
11. Building No. 59 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

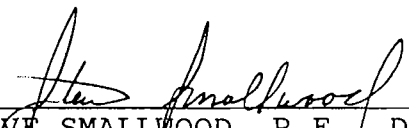
PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this 17th day
of February, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION



STEVE SMALLWOOD, P.E. Director
Division of Air Resources
Management

12-27-91

~~PL~~
DA
CNF,

OK BA

FYI, review, edit,
etc., and seal. Please
initial and forward.

Glubos
Bm

Bruce: 2-5-92
Re: Before final permit is issued:
ACOS-205848
Page 5. S.C.#1

"VOC emissions...
2.0 TPY it should
be 3.0 TPY. Hi is typo!
Call Constantin
at Harris Semiconductors
if you have questions
(407) 727-5732
Thanks, Teresa

Harris Semiconductors
(Electronic System)
Call: Constantin
(407) 727-5732

#1
should be
3.0 TPY

Constantine

407-727-5732

	VOC	ACID
57	↑ 2.0-3.0	
55	↑ 0.3-1.0	
54	↓ 75.5-73.8	↓ 9.9-9.7
59		↑ 0.1-0.3

75.5
73.8

1.7

pkw: 1027
JE: 80
#226

3-6-92
7:54 - 10:12

Bldg: 54
S O I

2
3

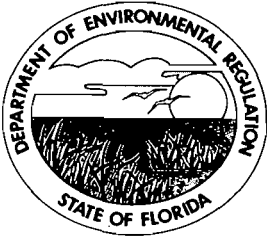
Just
10-22-91
10-23-91
10-23-91

0.95 lbs/hr VOC
3.33 " VOC
2.02 lbs/hr VOC

contact

John Widell

407-729-4076



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

10
January 8 1992
~~December 31, 1991~~

CERTIFIED MAIL-RETURN RECEIPT REQUESTED

Mr. John R. Steiner
Director of Facilities and Environmental Affairs
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32902-0883

Dear Mr. Steiner:

Attached is one copy of the Technical Evaluation and Preliminary Determination and proposed permits for Harris Semiconductor to modify its facility (i.e., Bldgs./sources 54, 55, 57 & 59), which includes an increase in the potential/allowable volatile organic compounds/organic solvents (VOC) emissions (55 & 57), an increase in the potential acid emissions (59), and a decrease in the potential/allowable VOC and the potential acid emissions (54). Even though there will be no net change in the facility's total potential pollutant emissions, there will be a modification of the federally enforceable permit conditions currently applicable to each source.

Please submit any written comments you wish to have considered concerning the Department's proposed action to Mr. Preston Lewis of the Bureau of Air Regulation.

Sincerely,

C. H. Fancy, P.E.
Chief
Bureau of Air Regulation

CHF/BM/rbm

Attachments

c: C. Collins, Central District
C. Triantafyllidis, HS
S. McClarty, P.E., HS

Technical Evaluation
and
Preliminary Determination

Harris Semiconductor
Brevard County
Palm Bay, Florida

Construction Permit Numbers:

AC 05-202415
AC 05-203985
AC 05-205848
AC 05-205849

Department of Environmental Regulation
Division of Air Resources Management
Bureau of Air Regulation

December 31, 1991



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-203985
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W

Project: Building 54 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 54, which is an existing source that utilizes hood type work stations for the manufacture of semiconductors, to permit a decrease in the potential acid and the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control systems are:

- o F54S01: a Beverly Pacific 50,000 scfm (43,141 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. PS-50HT;
- o F54S02: a Harrington 17,000 scfm (16,000 acfm) horizontal cross-flow wet scrubber, using PVC packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. ECH 66-9PBS; and,
- o F54S03: a Beverly Pacific 30,000 scfm (29,000 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. PS-24HT.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36

- o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated December 31, 1991.



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-202415
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 55 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 55, which is an existing source for the collection, short term storage, and shipping point for waste chemicals from the facility, to permit an increase in the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control system is:

- o F55S01: a Tri-Mer Corp. 9,500 scfm (7,500 acfm) horizontal counter-flow wet scrubber, using a polypropylene filter pack, and with a mist eliminator, for VOC and acid vapor removal; Model No. F/W 3.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36
o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent
Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated December 31, 1991.



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-205848
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 57 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 57, which is an existing source whose primary manufacturing operations are soldering and plating of integrated circuit parts, to permit an increase in the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control system is:

- o F57S01: a Tri-Mer Corp. 13,500 scfm (9,328 acfm) horizontal counter-flow wet scrubber, using a polypropylene filter pack, and with a mist eliminator, for VOC and acid vapor removal; Model No. F/W 5.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36
o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent
Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated December 31, 1991.



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-205849
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 59 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 59, which is an existing source used for the manufacture of semiconductors, to permit an increase in the potential acid emissions. The scrubber control and exhaust systems are:

Reliability Shop:

- o F59SO1: a Beverly Pacific 40,000 scfm (30,838 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator for acid vapor removal; Model No. PS-40HT;
- o F59SO2: a Beverly Pacific 20,000 scfm (10,972 acfm) vertical counter-current wet scrubber, using polypropylene packing, with a PVC mist eliminator, for VOC (volatile organic compounds/organic solvents) vapor removal; Model No. PS-24VT; and,

Probe Card Repair Shop:

- o F59EO4: an exhaust fan.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36

- o Cold Solvent Cleaning/ Stripping 4-01-003-99 Tons VOC/solvent Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated December 31, 1991.

*Bruce
a few questions
Please note/convert
and continue review.
Thanks for
Choice to revisit
1/2/92*

location?

State of Florida
Department of Environmental Regulation
Notice of Intent to Issue

The Department of Environmental Regulation (Department) hereby gives notice of its intent to issue permits (AC 05-203985: Bldg. 54; AC 05-202415: Bldg. 55; AC 05-205848: Bldg. 57; and, AC 05-205849: Bldg. 59) to Harris Semiconductor, Post Office Box 883, Melbourne, Florida 32902-0883. The project includes an increase in the potential/allowable volatile organic compounds/organic solvents (VOC) emissions for sources/Bldgs. 55 & 57, an increase in the potential acid emissions for source/Bldg. 59, and a decrease in the potential/allowable VOC and the potential acid emissions for source/Bldg. 54. Even though there will be a no net change in the facility's total potential pollutant emissions (i.e., VOC and acid), there will be a modification of the federally enforceable permit conditions currently applicable to each source. A determination of Best Available Control Technology (BACT) was not required. The Department is issuing this Intent to Issue for the reasons stated in the Technical Evaluation and Preliminary Determination.

A person whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative proceeding (hearing) in accordance with Section 120.57, Florida Statutes (F.S.). The petition must contain the information set forth below and must be filed (received) in the Office of General Counsel of the Department at 2600 Blair Stone Road, Tallahassee, Florida 32399-2400, within fourteen (14) days of publication of this notice. Petitioner shall mail a copy of the petition to the applicant at the address indicated above at the time of filing. Failure to file a petition within this time period shall constitute a waiver of any right such person may have to request an administrative determination (hearing) under Section 120.57, F.S.

The Petition shall contain the following information:

- (a) The name, address, and telephone number of each petitioner, the applicant's name and address, the Department's Permit File Number and the county in which the project is proposed;
- (b) A statement of how and when each petitioner received notice of the Department's action or proposed action;
- (c) A statement of how each petitioner's substantial interests are affected by the Department's action or proposed action;
- (d) A statement of the material facts disputed by Petitioner, if any;
- (e) A statement of facts which petitioner contends warrant reversal or modification of the Department's action or proposed action;

CAPE PUBLICATIONS, INC.

The Times

Published Weekly on Wednesday

THE TRIBUNE

Published Weekly on Wednesday

STAR-ADVOCATE

Published Weekly on Wednesday

RECEIVED

JAN 23 1992



Published Daily

Bureau of Air Regulation

STATE OF FLORIDA COUNTY OF BREVARD

Before the undersigned authority personally appeared Sandra N. Thomas who on

oath says that he/she is Legal Advertising Clerk

of the FLORIDA TODAY, a newspaper published in Brevard County,

Florida; that the attached copy of advertising being a

Legal Notice

in the matter of

Harris Semiconductor

in the

Court

was published in the FLORIDA TODAY NEWSPAPER

in the issues of January 21, 1992

Affiant further says that the said FLORIDA TODAY NEWSPAPER

is a newspaper published in said Brevard County, Florida and that the said newspaper has

heretofore been continuously published in said Brevard County, Florida regularly as stated above,

and has been entered as second class mail matter at the post office in COCOA

said Brevard County, Florida for a period of one year next preceeding the first publication of the

attached copy of advertisement; and affiant further says that he has neither paid nor promised any

person, firm or corporation any discount, rebate, commission or refund for the purpose of securing

this advertisement for publication in said newspaper.

Sandra N. Thomas

Sworn and subscribed to before me this

21 day of January A.D.

Leah Smith



OFFICIAL SEAL

LEAH SMITH MY COMMISSION EXPIRES JUNE 07, 1992

cc: G. Mitchell G. Zabini, Chief

TO: 10944-17-1/21, 1992, Y...

State of Florida Department of Environmental Regulation

of Intent to Issue The Department of Environmental Regulation (Department) hereby gives notice of its intent to issue permits (AC 03-20283; Bldg. 34; AC 03-202415; Bldg. 35; AC 03-202848; Bldg. 37; and AC 03-202849; Bldg. 39) to Harris Semiconductor, Post Office Box 2823, Melbourne, Florida 32902-823. The facility is located along Palm Bay Road in the City of Palm Bay. The project includes an increase in the potential/allowable volatile organic compounds/organic solvents (VOC) emissions for sources/Bldgs. 35 & 37, an increase in the potential acid emissions for source/Bldg. 39, and a decrease in the potential/allowable VOC and the potential acid emissions for source/Bldg. 34. Even though there will be a net change in the facility's total potential pollutant emissions (i.e., VOC and acid), there will be a modification of the federally enforceable permit conditions currently applicable to each source. A determination of Best Available Control Technology (BACT) was not required. The Department is issuing this intent to issue for the reasons stated in the Technical Evaluation and Preliminary Determination.

A person whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative proceeding (hearing) in accordance with section 120.57, Florida Statutes (F.S.). The petition must contain the information set forth below and must be filed (received) in the Office of General Counsel of the Department at 2400 Blair Stone Road, Tallahassee, Florida 32399-3400, within fourteen (14) days of publication of this notice. Petitioner shall mail a copy of the petition to the applicant at the address indicated above at the time of filing. Failure to file a petition within this time period shall constitute a waiver of any right such person may have to request an administrative determination (hearing) under Section 120.57, F.S.

The Petition shall contain the following information: (a) The name, address, and telephone number of each petitioner, the applicant's name and address, the Department's Permit File Number and the county in which the project is proposed; (b) A statement of how and when each petitioner received notice of the Department's action or proposed action; (c) A statement of how each petitioner's substantial interests are affected by the Department's action or proposed action; (d) A statement of the material facts (disputed by Petitioner) if any; (e) A statement of facts which petitioner contends warrant reversal or modification of the Department's action or proposed action; (f) A statement of which rules or statutes petitioner contends require reversal or modification of the Department's action or proposed action; and (g) A statement of the relief sought by petitioner, stating precisely the action petitioner wants the Department to take with respect to the Department's action or proposed action.

If a petition is filed, the administrative hearing process is deemed to formulate agency action. Accordingly, the Department's final action may be different from the position taken by it in this notice. Persons whose substantial interests will be affected by any decision of the Department with respect to the applications have the right to petition to become a party to the proceedings. The petition must conform to the requirements specified above and be filed (received) within 14 days of publication of this notice in the Office of General Counsel at the above address of the Department. Failure to petition within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, F.S., and to participate as a party to this proceeding. Any subsequent intervention will only be at the approval of the presiding officer upon motion filed pursuant to Rule 23-5.207, Florida Administrative Code.

The applications are available for public inspection during business hours, 8:00 a.m. to 5:00 p.m., Monday through Friday, except legal holidays, at: Department of Environmental Regulation Bureau of Air Regulation 2400 Blair Stone Road Tallahassee, FL 32399-3400 Department of Environmental Regulation Central District 217 Alapaha Blvd., Suite 220 Orlando, FL 32803-3767

Any person may send written comments on the proposed action to Mr. Preston Lewis at the Department's Tallahassee address. All comments received within 14 days of the publication of this notice will be considered in the Department's final determination.

Handwritten notes: 30 ORL 05 0014 41 Bldg 57 32 55 54 34504 09 154504 33 503 34504 10 59 11 AC0580D 707



HARRIS · RCA · GE · INTERSIL

HARRIS CORPORATION

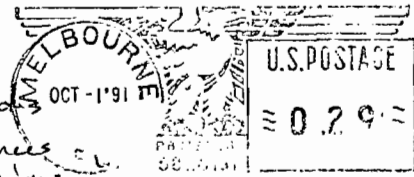
SEMICONDUCTOR SECTOR
P.O. BOX 883
MELBOURNE, FL 32902-0883

glo

10-4-91

Q 4115

spots D.C.T. DHD on amend. vs mod.
and sees: o to send a letter on exp. d. 3
o ✓ for 1000 for 4 reasons
and like similar emissions
and < 25 TPT change. *B*



Bureau of Air Quality Management
Florida Department of Environmental Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, Florida 32399-2400

Attention: Mr. Bruce Mitchell, Engineer





RECEIVED

OCT 03 1991

September 27, 1991

Division of Air Resources Management

Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Subject: Extension of Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189178 (Bldg. 57); AC 05-189176 (Bldg. 58); AC 05-180707 (Bldg. 59); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

Dear Mr. Fancy:

In accordance with F.A.C. rule 17-4.090 and Specific Condition No. 13 of the above mentioned air permits, the purpose of this letter is to request an extension of the expiration dates until April 30th, 1992.

This extension will accommodate project schedules to accomplish the air emissions monitoring for Buildings 54, 55, 58 and 62 as specified in the recent amendments to those Building Construction permits.

Furthermore, we request that the VOC/solvent emissions limit to Building 57 be increased from 2.0 to 3.0 tons a year and Building 55 from 0.3 to 1.0 ton a year. An additional buffer over the actual emissions will allow for any variations in production schedules with the resulting fluctuations in chemical activity and air emissions in those Buildings. In turn, we request that the permit limit for Building 54 be reduced from 75.5 to 73.8 tons a year.

Lastly, we request that the potential acid emissions for Building 59 be raised from 0.1 to 0.3 tons a year and in turn be reduced for Building 54 from 9.9 to 9.7. This increase will similarly allow for variations in the production schedules.

Operating permit applications for all applicable Buildings of the site will be submitted soon after the aforementioned tasks have been completed.

Handwritten list: 202415 55, 203985 54, 205848 57, 205849 59, HS

Handwritten notes: TOP, Start Control, End Control, Page 1 of 2

Should you have any questions or require any additional information please contact our office at (407) 729-5301.

Yours Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services

cc: D. Bock, Harris Semiconductor Sector
D. Erdley, Harris Corp. Headq.
C. Collins, P.E., Orlando DER
B. Mitchell, Tallahassee DER

\extrnrgst.4



RECEIVED

October 22, 1991

OCT 24 1991

Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Bureau of
Air Regulation

Subject: Extension of Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189176 (Bldg. 58); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

Dear Mr. Fancy:

In accordance with F.A.C. rule 17-4.090 and Specific Condition No. 13 of the above mentioned air permits, the purpose of this letter is to request an extension of the expiration dates until June 30th, 1992.

This extension will accommodate project schedules to accomplish the air emissions monitoring for Buildings 54, 55, 58 and 62 as specified in the recent amendments to those Building Construction permits.

Operating permit applications for all applicable Buildings of the site will be submitted soon after the aforementioned tasks have been completed.

Should you have any questions or require any additional information please contact our office at (407) 729-5301.

Yours Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services

cc: D. Bock, Harris Semiconductor Sector
D. Erdley, Harris Corp. Headq.
C. Collins, P.E., Orlando DER
B. Mitchell, Tallahassee DER

\extrnrqst.4



October 22, 1991

Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Subject: Extension of Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189176 (Bldg. 58); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

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This extension will accommodate project schedules to accomplish the air emissions monitoring for Buildings 54, 55, 58 and 62 as specified in the recent amendments to those Building Construction permits.

Operating permit applications for all applicable Buildings of the site will be submitted soon after the aforementioned tasks have been completed.

Should you have any questions or require any additional information please contact our office at (407) 729-5301.

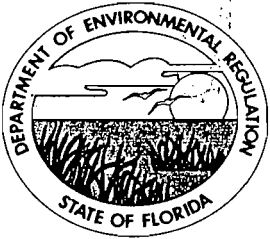
Yours Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services

cc: D. Bock, Harris Semiconductor Sector
D. Erdley, Harris Corp. Headq.
C. Collins, P.E., Orlando DER
B. Mitchell, Tallahassee DER

\extrnrgst.4



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

December 5, 1991

CERTIFIED MAIL - RETURN RECEIPT REQUESTED

Bucci's

Mr. John R. Steiner
Director of Facilities and Environmental Affairs
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32902-0883

Dear Mr. Steiner:

Re: Expiration Date Extension for Construction Permits

AC 05-189176: Bldg. 58
AC 05-190797: Bldg. 62
AC 05-190799: Bldg. 62⁵⁵
AC 05-190800: Bldg. 54

The Department has reviewed the above request for expiration date extensions contained in Mr. Constantine Triantafyllidis's letter received October 24, 1991. The request is acceptable and the following will be changed and added:

1. Expiration Date

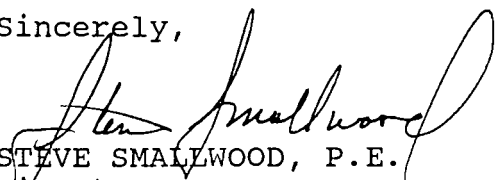
From: December 31, 1991
To: June 30, 1992

2. Attachments to be Incorporated

- o Mr. Constantine Triantafyllidis's letter received October 3, 1991.
- o Mr. Constantine Triantafyllidis's letter received October 24, 1991.

This letter must be attached to the construction permits, Nos. AC 05-189176, -190797, -190799 & -190800, and shall become a part of the permits.

Sincerely,


STEVE SMALLWOOD, P.E.
Director
Division of Air Resources
Management

Mr. John R. Steiner
Page Two

SS/BM/rbm

Attachments

cc: C. Collins, CD
C. Triantafyllidis, HS
L. Hutker, P.E., HS

September 27, 1991

Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Subject: Extension of Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189178 (Bldg. 57); AC 05-189176 (Bldg. 58); AC 05-180707 (Bldg. 59); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

Dear Mr. Fancy:

In accordance with F.A.C. rule 17-4.090 and Specific Condition No. 13 of the above mentioned air permits, the purpose of this letter is to request an extension of the expiration dates until April 30th, 1992.

This extension will accommodate project schedules to accomplish the air emissions monitoring for Buildings 54, 55, 58 and 62 as specified in the recent amendments to those Building Construction permits.

Furthermore, we request that the VOC/solvent emissions limit to Building 57 be increased from 2.0 to 3.0 tons a year and Building 55 from 0.3 to 1.0 ton a year. An additional buffer over the actual emissions will allow for any variations in production schedules with the resulting fluctuations in chemical activity and air emissions in those Buildings. In turn, we request that the permit limit for Building 54 be reduced from 75.5 to 73.8 tons a year.

Lastly, we request that the potential acid emissions for Building 59 be raised from 0.1 to 0.3 tons a year and in turn be reduced for Building 54 from 9.9 to 9.7. This increase will similarly allow for variations in the production schedules.

Operating permit applications for all applicable Buildings of the site will be submitted soon after the aforementioned tasks have been completed.

Should you have any questions or require any additional information please contact our office at (407) 729-5301.

Yours Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services

cc: D. Bock, Harris Semiconductor Sector
D. Erdley, Harris Corp. Headq.
C. Collins, P.E., Orlando DER
B. Mitchell, Tallahassee DER

\extrqst.4



RECEIVED

October 22, 1991

OCT 24 1991

Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Bureau of
Air Regulation

Subject: Extension of Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189176 (Bldg. 58); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

Dear Mr. Fancy:

In accordance with F.A.C. rule 17-4.090 and Specific Condition No. 13 of the above mentioned air permits, the purpose of this letter is to request an extension of the expiration dates until June 30th, 1992.

This extension will accommodate project schedules to accomplish the air emissions monitoring for Buildings 54, 55, 58 and 62 as specified in the recent amendments to those Building Construction permits.

Operating permit applications for all applicable Buildings of the site will be submitted soon after the aforementioned tasks have been completed.

Should you have any questions or require any additional information please contact our office at (407) 729-5301.

Yours Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services

cc: D. Bock, Harris Semiconductor Sector
D. Erdley, Harris Corp. Headq.
C. Collins, P.E., Orlando DER
B. Mitchell, Tallahassee DER

\extnrqst.4



RECEIVED

September 5, 1991

SEP 11 1991

Division of Air
Resources Management

Mr. Claire Fancy
Bureau Chief
Bureau of Air Regulation
Florida Department of Environmental Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Re: Exhaust system modification; Permit Number AC 05-190799
Building 55 Air Permit, Harris Semiconductor.

Dear Mr. Fancy:

By this letter, Harris Semiconductor is requesting the Department to modify Permit Number AC 05-190799 as recently amended (see attached July 18, 1991 letter), to include the addition of a small source described below.

A solvent rinse station is proposed to be added to the exhaust system for the rinse of empty bottles containing remnants of the chemical Stripper, EKC Burmar NRS 1020. A copy of the MSDS of this chemical is attached with this submittal. The rinseate will be collected in a drum and shipped offsite for disposal. The exhaust requirement for this station has been calculated to be at 600 cfm. The potential emissions to the scrubber from this operation were estimated at 14 pounds per year.

If the Department has no objection, we will proceed with the course of action described above with completion by October 10th. If you have any questions or require any additional information, please contact me at (407) 729-5301.

Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer

cc: B. Mitchell, Tallahassee
C. Collins, Orlando
K. Smith
D. Bock
N. Baldisserotto



July 18, 1991

Mr. Claire Fancy
Bureau Chief
Bureau of Air Regulation
Florida Department of Environmental Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Re: Exhaust system modification; Permit Number AC 05-190799
Building 55 Air Permit, Harris Semiconductor.

Dear Mr. Fancy:

By this letter, Harris Semiconductor is providing the Department with notice of its intent to replace scrubber number F55S01 (Permit Number AC 05-190799) with a larger capacity wet scrubber system which will be renumbered F55S01. Consequently, an amendment to the above mentioned permit is requested.

The replacement scrubber for the above system is a Tri-Mer model F/W 3 horizontal counter flow scrubber rated for 9,500 scfm of air flow. The scrubber will be located on the roof of Building 55 at a height of 29 feet (the height of the roof is 17 feet) and will replace the F55S01, 1,000 scfm rated Harrison scrubber, Model No. HF-10 that is currently servicing the Building.

The proposed design will incorporate the existing bottle crushing operation into the exhaust system and thus minimize any VOC/Solvent emissions from that process. The exhaust system currently includes the acid bottle wash stations and a station used for the release of chemicals from damaged 'bubbler' containers as described in the process description for the building enclosed with this submittal.

Information on the existing scrubber system is provided in Attachment I and information on the replacement Tri-Mer model F/W 3 scrubber is provided in Attachment II. A list of the most commonly used chemicals which are anticipated to be exhausted to the proposed scrubber is also included in Attachment II. The proposed exhaust requirements for the operations at Building 55 can be handled adequately by the replacement scrubber.

If the Department has no objection, we will proceed with the course of action described above with completion by the end of August.

In addition, enclosed please find a letter executed by Mr. John Cornell, President of Harris Semiconductor, authorizing Mr. John Steiner, Director of Environmental and Facilities to represent the owner.

If you have any questions or require any additional information, please contact me at (407) 729-5301.

Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer

cc: B. Mitchell, Tallahassee
C. Collins, Orlando
K. Smith
J. Steiner
D. Bock

Materi | Safety Data Sheet

BURMAR NRS 1020

Manufacturer's Name: **EKC Technology, Inc.**
Address: **P.O. Box 3703, Hayward, CA 94540**
Emergency Telephone No.: **Chemtec (800) 424-9300**
Other Information Calls: **(415) 887-3711**
Signature of Person Responsible for Preparation: *Michael David / Henry*
Date Prepared: **January 12, 1990**

SECTION 1 - IDENTITY

Common Name (used on label) (Trade Name & Synonyms): **Burmar NRS 1020**
Chemical Name: **Photoresist Stripper**
Formula: **Not Available**
Can No.: **See Section 2 Below**
Chemical Family: **Organic Acid/Solvent Blend**

SECTION 2 - HAZARDOUS INGREDIENTS

Principal Hazardous Component(s) (chemical & common name(s))	%	Threshold Limit Value (units)
INGREDIENT (CAS #)		OSHA PEL/ACGIH
Dodecylbenzenesulfonic Acid (68584-22-5)	Proprietary	-----/-----
Aromatic Hydrocarbon Solvent (64742-94-5)	Proprietary	500 ppm/-----

SECTION 3 - PHYSICAL & CHEMICAL CHARACTERISTICS (Fire & Explosion Data)

Boiling Point: **Range 400 - 580°F**
Flash Point: **Greater Than 1**
Vapor Density (Air = 1): **Greater Than 1**
Specific Gravity (H₂O = 1): **0.95-1.00**
Evaporation Rate (H₂O = 1): **NDA**
Vapor Pressure (mm Hg): **0.4 mm Hg @ 68°F**
Solubility in Water: **Negligible**
Sensitivity in Water: **None**
Appearance and Odor: **Purple red color liquid with aromatic odor.**

Flash Point: **over 200°F**
Flammable Limits in Air % by Volume: **NDA**
Lower: **NDA**
Upper: **NDA**
Extinguisher: **Water, Fog, Alcohol, Foam, CO₂, Dry Chemical**
Auto-Ignition Temperature: **NDA**

Special Fire Fighting Procedures: **The use of self-contained breathing apparatus is recommended. Do not use water except as fog. Avoid breathing vapor or fumes.**

Unusual Fire and Explosion Hazards: **Do not mix or store with strong oxidants. Keep work areas free of sources of ignition. Moderately combustible liquid.**

NDA = No Data Available

TITLE

STRIPPER, EKC BURMAR NRS 1020

BURMAR NRS 1020 1/12/90

SECTION 4 - PHYSICAL HAZARDSStability Unstable Conditions to Avoid UnknownIncompatibility Materials to Avoid Corrosive when mixed with water; strong heat with strong alkali, oxidants.Hazardous Decomposition Products Fumes, smoke, carbon monoxide in case of incomplete combustion.Hazardous Polymerization May Occur Conditions to Avoid Unknown**SECTION 5 - HEALTH HAZARDS**Threshold Limit Value See Section 2 for individual component TLV values.Signs and Symptoms of Exposure Acute Respiratory tract irritation. Headache, dizziness, nausea. Overexposure Corrosive burns to eyes. Chronic Overexposure Skin irritation, corrosive burns with prolonged or repeated contact.Medical Conditions Generally Approved by Exposure UnknownChemical Listed as Carcinogen or Potential Carcinogen National Toxicology Program Yes No IARC Monographs Yes No OSHA Yes No OSHA Permissible Exposure Limit See Section 2 ACGIH Threshold Limit Value See Section 2 Other Exposure Limits Used Not Applicable**Emergency and First Aid Procedures** Inhalation Remove victim to fresh air. Seek immediate medical attention. Eye Flush eyes with water at least 15 minutes. Seek immediate medical attention. Skin Wash skin with soap and water. Seek medical attention if irritation persists. Ingestion DO NOT INDUCE VOMITING. Seek immediate medical attention.**SECTION 6 - SPECIAL PROTECTION INFORMATION**Respiratory Protection Hydrocarbon vapor canister or supplied air respiratory protection for exposures above TLV. Specify TypeVentilation Local Use Only With Mechanical Exhaust Hood Exhaust General Not Applicable Special None Other NoneProtective Gloves Use Chemical Resistant Gloves. Eye Protection Use Splash Goggles or Face Shield.Other Protective Clothing or Equipment Use chemical resistant apron/clothing to avoid repeated or prolonged contact.**SECTION 7 - SPECIAL PRECAUTIONS AND SPILL/LEAK PROCEDURES**Precautions to be Taken in Handling and Storage Keep container closed when not in use. Do not handle or store near heat, spark, open flame, or strong oxidants. Ventilation required.Other Precautions Avoid inhalation of vapor, direct contact with product. Remove contaminated clothing, launder before reuse. Wash skin thoroughly with soap and water after handling material.Steps to be Taken in Case Material is Released or Spilled REMOVE ALL SOURCES OF IGNITION. Keep people away. Add absorbant to spill or flush with water. Remove absorbant to open, well ventilated area. Avoid contact with skin, eyes or breathing vapors.Waste Disposal Methods Dispose of used product in accordance with local, state and federal regulations.

Consult with EKC Technology, Inc. hazardous material staff for additional information.

The above data is for information purposes only and is accurate to the best of EKC Technology, Inc.'s knowledge. No guarantee or liability is expressed or implied.

TITLE

STRIPPER, EKC BURMAR NRS 1020



JON E. CORNELL
President

RECEIVED

OCT 24 1991

Division of Air
Resources Management

6 March 1991

TO WHOM IT MAY CONCERN:

I, Jon E. Cornell, President of HARRIS SEMICONDUCTOR, a sector within HARRIS CORPORATION, do hereby authorize John Steiner, Sector Director of Facilities and Environmental Affairs of said HARRIS SEMICONDUCTOR, to execute applications for Pollution Source permits to the Department of Environmental Regulation of the State of Florida, and the United States Environmental Protection Agency. Mr. Steiner is further authorized to sign monitoring reports and execute other correspondence related to these permits for the Harris Semiconductor, Melbourne, Florida site.

A handwritten signature in black ink, appearing to read 'Jon E. Cornell', written in a cursive style.

Jon E. Cornell

RECEIVED
DER - MAIL ROOM

LETTER OF TRANSMITTAL: 03
1991 OCT 24

Date: October 22, 1991

RECEIVED

To: Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
2600 Blair Stone Road
Tallahassee, FL 32399

OCT 24 1991

Bureau of
Air Regulation

Re: Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189178 (Bldg. 57); AC 05-189176 (Bldg. 58); AC 05-180707 (Bldg. 59); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

WE ARE SENDING YOU:

- Attached
- Under Separate Cover
- Blueprints
- Copy of Letter

THESE ARE TRANSMITTED:

- For approval
- For Your Use
- As Requested
- For Review and Comment

Copies	Date	No.	Description
1	10/22/91	1	Letter of request for extension of permits for Bldgs. 54, 55, 58, 62.
1	10/22/91	2	Letter by a Company officer authorizing Mr. John Steiner, Director of Environmental and Facilities, to represent the owner.
1	10/22/91	3	Permit Application Fee for \$1000.00
4	10/22/91	4	Modification to permit application for Bldgs. 54, 55, 57, 59.

REMARKS: Dear Mr. Clair:

Should you have any questions or require any additional information in regards to the above mentioned submittal please, contact me at (407) 729-5301.

cc: D. Bock

Signed: Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.

LETTER OF TRANSMITTAL

RECEIVED
OCT 24 1991
Division of Air
Resources Management

Date: October 22, 1991

To: Mr. Clair H. Fancy
Bureau Chief
Bureau of Air Regulation
2600 Blair Stone Road
Tallahassee, FL 32399

Re: Construction Permits AC 05-190800 (Bldg. 54); AC 05-190799 (Bldg. 55); AC 05-189178 (Bldg. 57); AC 05-189176 (Bldg. 58); AC 05-180707 (Bldg. 59); AC 05-190797 (Bldg. 62), Harris Semiconductor, Melbourne.

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4	10/22/91	4	Modification to permit application for Bldgs. 54, 55, 57, 59.

10/22
Bruce:
All these
have been
submitted
to Mr
C. Fancy

REMARKS: Dear Mr. Clair:

Should you have any questions or require any additional information in regards to the above mentioned submittal please, contact me at (407) 729-5301.

cc: D. Bock

Signed: Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.



RECEIVED

SEP 16 1991

Division of Air
Resources Management

September 12, 1991

Mr. Claire Fancy
Bureau Chief
State of Florida
Department of Environmental Regulation
Bureau of Air Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Subject: Processing Fee for the Modification to Construction Permit Number
AC 05-190799 for Building 55, Harris Semiconductor.

Dear Mr. Fancy:

Please, find enclosed a check for \$ 250 to accompany the letter dated 9/5/1991 requesting a minor modification to the Construction Permit for Building 55 at Harris Semiconductor, Palm Bay facility.

If you have any questions or require any additional information, please contact me at (407) 729-5301.

Sincerely,

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services
Harris Semiconductor

cc: B. Mitchell
K. Smith



HARRIS CORPORATION
SEMICONDUCTOR SECTOR

THE FIRST NATIONAL BANK OF ATLANTA
AUGUSTA, GEORGIA

64-1327
611

17370

PAY

DATE

08/01/91

CHECK NO.

00173704

NET AMOUNT

*****250.

TWO HUNDRED FIFTY AND 00/100 DOLLARS

TO THE
ORDER
OF

FLORIDA DEPT. OF ENVIRONMENTAL
REGULATION
2600 BLAIR STONE RD.
TALLAHASSEE, FL

HARRIS CORPORATION
SEMICONDUCTOR SECTOR

32399

COUNTERSIGNED

AUTHORIZED SIGNATURE

Subject: Processing Fee for the Modification to Construction Permit Number
AC 05-190799 for Building 55, Harris Semiconductor.

Dear Mr. Fancy:

Please, find enclosed a check for \$ 250 to accompany the letter dated 9/5/1991
requesting a minor modification to the Construction Permit for Building 55 at
Harris Semiconductor, Palm Bay facility.

If you have any questions or require any additional information, please contact
me at (407) 729-5301.

Sincerely,

Constantine Triantafyllidis

Constantine Triantafyllidis, R.E.P.
Environmental Engineer
Environmental Services
Harris Semiconductor

cc: B. Mitchell
K. Smith

*Bruce
got the check
from Harris
9-16-91
AC 05-202415*



October 22, 1991

Mr. Bruce Mitchell
Engineer
Bureau of Air Regulation
Florida Department of Environmental Regulation
Twin Towers Office Building
2600 Blair Stone Road
Tallahassee, FL 32399-2400

Re: Exhaust system modification; Permit Number AC 05-190800 Building 54, Harris Semiconductor, Palm Bay.

Dear Bruce:

In regards to our telephone conversation of October 3, 1991 please review the following information and attached drawing in regards to the scrubber modifications at Building 54.

Building 54 West

Scrubber numbers F54S01 and F54S02 (20,000 scfm each Harrison scrubbers) were replaced by scrubber number F63S01. The replacement scrubber is a Beverly Pacific model number PS-50HT rated for 50,000 scfm (See Attachment I, Control Equipment for further information). The scrubber was renumbered F54S01 and is located to the northwest of the Building at ground level.

Building 54 East

Scrubber number F54S03 (23,000 scfm Harrison scrubber) was replaced by scrubber F62S01. The replacement scrubber is a Beverly Pacific model number PS-24HT rated for 30,000 scfm. The scrubber was renumbered F54S03 and is located to the northeast of the Building at ground level.

Scrubber number F54S04 (23,000 scfm Harrison scrubber) was replaced by another scrubber, not used previously in this facility. The replacement scrubber is a Harrington model number ECH66-9PBS rated for 17,000 scfm. The scrubber was renumbered F54S02 and is located to the northeast of the Building at ground level and at a more northerly position to the F54S03.

Information on the existing scrubber scheme and the Building 54 dimensions is provided in Attachment I and the accompanying drawing.

If you have any questions or require any additional information, please contact me at (407) 729-5301.

Sincerely,

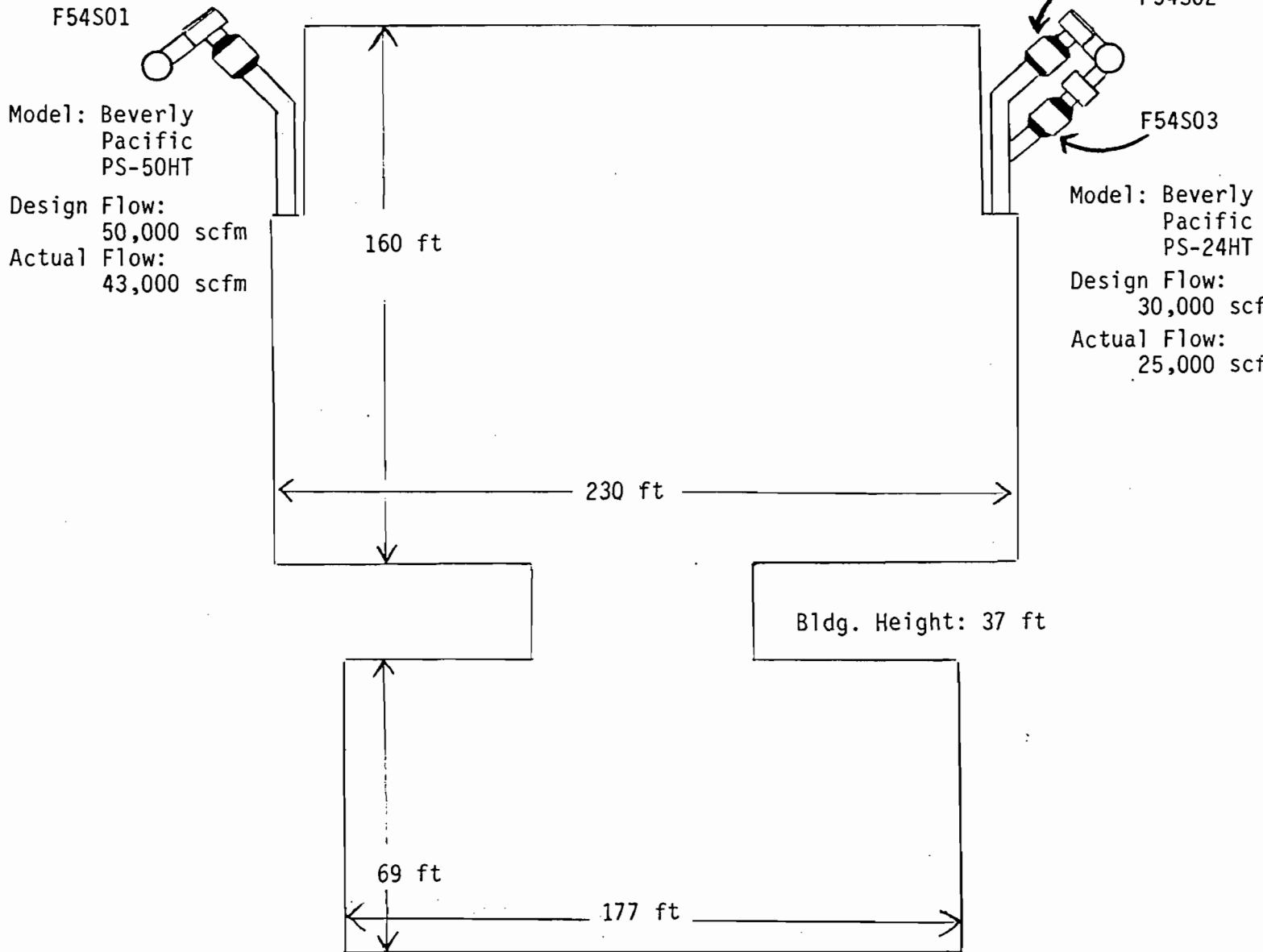
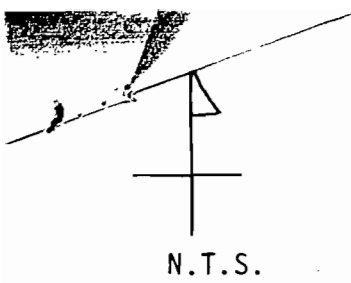
Constantine Triantafyllidis

Constantine Triantafyllidis, REP
Environmental Engineer







cc: D. Bock

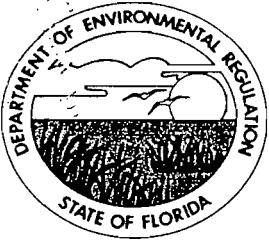
HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 54

Model: Harrington, ECH66-9P
Design Flow: 17,000 scfm
Actual Flow: 15,000 scfm



LEGEND

-  - Horizontal Scrubber
-  - Vertical Scrubber
-  - Exhaust Stack
-  - Exhaust Fan
-  - Stack mounted on Fan
-  - Epitaxial Scrubber



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

January 10, 1992

CERTIFIED MAIL-RETURN RECEIPT REQUESTED

Mr. John R. Steiner
Director of Facilities and Environmental Affairs
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32902-0883

Dear Mr. Steiner:

Attached is one copy of the Technical Evaluation and Preliminary Determination and proposed permits for Harris Semiconductor to modify its facility (i.e., Bldgs./sources 54, 55, 57 & 59), which includes an increase in the potential/allowable volatile organic compounds/organic solvents (VOC) emissions (55 & 57), an increase in the potential acid emissions (59), and a decrease in the potential/allowable VOC and the potential acid emissions (54). Even though there will be no net change in the facility's total potential pollutant emissions, there will be a modification of the federally enforceable permit conditions currently applicable to each source.

Please submit any written comments you wish to have considered concerning the Department's proposed action to Mr. Preston Lewis of the Bureau of Air Regulation.

Sincerely,

C. H. Fancy, P.E.
Chief
Bureau of Air Regulation

CHF/BM/rbm

Attachments

c: C. Collins, Central District
C. Triantafyllidis, HS
S. McClarty, P.E., HS

BEFORE THE STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

In the Matter of
Application for Permits by:

Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32902-0883

DER File Nos. AC 05-202415
AC 05-203985
AC 05-205848
AC 05-205849

INTENT TO ISSUE

The Department of Environmental Regulation (Department) hereby gives notice of its intent to issue air construction permits (copies attached) for the proposed projects as detailed in the applications specified above. The Department is issuing this Intent to Issue for the reasons stated in the attached Technical Evaluation and Preliminary Determination.

The applicant, Harris Semiconductor, applied on October 24, 1991, to the Department for permits to increase the potential/allowable volatile organic compounds/organic solvents (VOC) emissions in sources/Bldgs. 55 and 57, to increase the potential acid emissions in source/Bldg. 59, and to decrease the potential/allowable VOC and the potential acid emissions in source/Bldg. 54. Even though there will be no net change in the facility's total potential pollutant emissions, there will be a modification of the federally enforceable permit conditions currently applicable to each source.

The Department has permitting jurisdiction under Chapter 403, Florida Statutes (F.S.), and Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4. The project is not exempt from permitting procedures. The Department has determined that air construction permits are required for the proposed work.

Pursuant to Section 403.815, F.S., and Department Rule 17-103.150, F.A.C., you (the applicant) are required to publish at your own expense the enclosed Notice of Intent to Issue Permits. The notice shall be published one time only within 30 days, in the legal

ad section of a newspaper of general circulation in the area affected. For the purpose of this rule, "publication in a newspaper of general circulation in the area affected" means publication in a newspaper meeting the requirements of Sections 50.011 and 50.031, F.S., in the county where the activity is to take place. Where there is more than one newspaper of general circulation in the county, the newspaper used must be the one with significant circulation in the area that may be affected by the permits. If you are uncertain that a newspaper meets these requirements, please contact the Department at the address or telephone number listed below. The applicant shall provide proof of publication to the Department's Bureau of Air Regulation, 2600 Blair Stone Road, Tallahassee, Florida 32399-2400 (904-488-1344), within seven days of publication. Failure to publish the notice and provide proof of publication within the allotted time may result in the denial of the permits.

The Department will issue the permits with the attached conditions unless a petition for an administrative proceeding (hearing) is filed pursuant to the provisions of Section 120.57, F.S.

A person whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative proceeding (hearing) in accordance with Section 120.57, F.S. The petition must contain the information set forth below and must be filed (received) in the Office of General Counsel of the Department at 2600 Blair Stone Road, Tallahassee, Florida 32399-2400. Petitions filed by the permit applicant and the parties listed below must be filed within 14 days of receipt of this intent. Petitions filed by other persons must be filed within 14 days of publication of the public notice or within 14 days of receipt of this intent, whichever first occurs. Petitioner shall mail a copy of the petition to the applicant at the address indicated above at the time of filing. Failure to file a petition within this time period shall constitute a waiver of any right such person may have to request an administrative determination (hearing) under Section 120.57, F.S.

The Petition shall contain the following information:

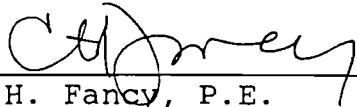
- (a) The name, address, and telephone number of each petitioner, the applicant's name and address, the Department Permit File Number and the county in which the project is proposed;
- (b) A statement of how and when each petitioner received notice of the Department's action or proposed action;
- (c) A statement of how each petitioner's substantial interests are affected by the Department's action or proposed action;

- (d) A statement of the material facts disputed by Petitioner, if any;
- (e) A statement of facts which petitioner contends warrant reversal or modification of the Department's action or proposed action;
- (f) A statement of which rules or statutes petitioner contends require reversal or modification of the Department's action or proposed action; and,
- (g) A statement of the relief sought by petitioner, stating precisely the action petitioner wants the Department to take with respect to the Department's action or proposed action.

If a petition is filed, the administrative hearing process is designed to formulate agency action. Accordingly, the Department's final action may be different from the position taken by it in this notice. Persons whose substantial interests will be affected by any decision of the Department with regard to the applications have the right to petition to become a party to the proceeding. The petition must conform to the requirements specified above and be filed (received) within 14 days of publication of this notice in the Office in General Counsel at the above address of the Department. Failure to petition within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, F.S., and to participate as a party to this proceeding. Any subsequent intervention will only be at the approval of the presiding officer upon motion filed pursuant to Rule 28-5.207, F.A.C.

Executed in Tallahassee, Florida.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION



C. H. Fancy, P.E.
Chief
Bureau of Air Regulation

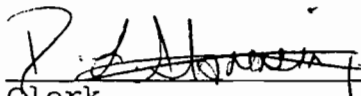
Copies furnished to:

c: C. Collins, Central District
C. Triantafyllidis, HS
S. McClarty, P.E., HS

CERTIFICATE OF SERVICE

The undersigned duly designated deputy clerk hereby certifies that this NOTICE OF INTENT TO ISSUE and all copies were mailed before the close of business on 1-10-92.

FILING AND ACKNOWLEDGEMENT
FILED, on this date, pursuant to
§120.52(9), Florida Statutes, with
the designated Department Clerk,
receipt of which is hereby
acknowledged.


Clerk

1-10-92
Date

State of Florida
Department of Environmental Regulation
Notice of Intent to Issue

The Department of Environmental Regulation (Department) hereby gives notice of its intent to issue permits (AC 05-203985: Bldg. 54; AC 05-202415: Bldg. 55; AC 05-205848: Bldg. 57; and, AC 05-205849: Bldg. 59) to Harris Semiconductor, Post Office Box 883, Melbourne, Florida 32902-0883. The facility is located along Palm Bay Road in the City of Palm Bay. The project includes an increase in the potential/allowable volatile organic compounds/organic solvents (VOC) emissions for sources/Bldgs. 55 & 57, an increase in the potential acid emissions for source/Bldg. 59, and a decrease in the potential/allowable VOC and the potential acid emissions for source/Bldg. 54. Even though there will be a no net change in the facility's total potential pollutant emissions (i.e., VOC and acid), there will be a modification of the federally enforceable permit conditions currently applicable to each source. A determination of Best Available Control Technology (BACT) was not required. The Department is issuing this Intent to Issue for the reasons stated in the Technical Evaluation and Preliminary Determination.

A person whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative proceeding (hearing) in accordance with Section 120.57, Florida Statutes (F.S.). The petition must contain the information set forth below and must be filed (received) in the Office of General Counsel of the Department at 2600 Blair Stone Road, Tallahassee, Florida 32399-2400, within fourteen (14) days of publication of this notice. Petitioner shall mail a copy of the petition to the applicant at the address indicated above at the time of filing. Failure to file a petition within this time period shall constitute a waiver of any right such person may have to request an administrative determination (hearing) under Section 120.57, F.S.

The Petition shall contain the following information:

- (a) The name, address, and telephone number of each petitioner, the applicant's name and address, the Department's Permit File Number and the county in which the project is proposed;
- (b) A statement of how and when each petitioner received notice of the Department's action or proposed action;
- (c) A statement of how each petitioner's substantial interests are affected by the Department's action or proposed action;
- (d) A statement of the material facts disputed by Petitioner, if any;
- (e) A statement of facts which petitioner contends warrant reversal or modification of the Department's action or proposed action;

(f) A statement of which rules or statutes petitioner contends require reversal or modification of the Department's action or proposed action; and,

(g) A statement of the relief sought by petitioner, stating precisely the action petitioner wants the Department to take with respect to the Department's action or proposed action.

If a petition is filed, the administrative hearing process is designed to formulate agency action. Accordingly, the Department's final action may be different from the position taken by it in this Notice. Persons whose substantial interests will be affected by any decision of the Department with regard to the applications have the right to petition to become a party to the proceeding. The petition must conform to the requirements specified above and be filed (received) within 14 days of publication of this notice in the Office of General Counsel at the above address of the Department. Failure to petition within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, F.S., and to participate as a party to this proceeding. Any subsequent intervention will only be at the approval of the presiding officer upon motion filed pursuant to Rule 28-5.207, Florida Administrative Code.

The applications are available for public inspection during business hours, 8:00 a.m. to 5:00 p.m., Monday through Friday, except legal holidays, at:

Department of Environmental Regulation
Bureau of Air Regulation
2600 Blair Stone Road
Tallahassee, Florida 32399-2400

Department of Environmental Regulation
Central District
3319 Maguire Blvd., Suite 232
Orlando, Florida 32803-3767

Any person may send written comments on the proposed action to Mr. Preston Lewis at the Department's Tallahassee address. All comments received within 14 days of the publication of this notice will be considered in the Department's final determination.

Technical Evaluation
and
Preliminary Determination

Harris Semiconductor
Brevard County
Palm Bay, Florida

Construction Permit Numbers:

AC 05-202415
AC 05-203985
AC 05-205848
AC 05-205849

Department of Environmental Regulation
Division of Air Resources Management
Bureau of Air Regulation

January 10, 1992

I. Application

A. Applicant

Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32902-0883

B. Project and Location

The applicant intends to modify its existing facility (i.e., Bldgs./sources 54, 55, 57 & 59), which includes an increase in the potential/allowable volatile organic compounds/organic solvents (VOC) emissions (55 & 57), an increase in the potential acid emissions (59), and a decrease in the potential/allowable VOC and the potential acid emissions (54). Even though there will be no net change in the facility's total potential pollutant emissions (i.e., VOC and acid), there will be a modification of the federally enforceable permit conditions currently applicable to each source.

The existing facility is located on Palm Bay Road in the City of Palm Bay, Brevard County, Florida.

The UTM coordinates are Zone 17, 538.7 km North and 3100.9 km West.

C. Process and Controls

Since the project's intent is to provide a buffer above the actual emissions of the sources (increases) and to bring the potential emissions more in line with source operations (decreases), there will be no change in the processing activities and the control systems.

D. The Standard Industrial Classification Codes:

- o Buildings 54, 55, 57 & 59:
Cold Solvent Cleaning/ 40-01-003-99 Tons VOC/Solvent
Stripping Consumed

II. Rule Applicability

The proposed project is subject to preconstruction review under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July 1, 1990 version).

The application packages were deemed complete on October 24, 1991.

The existing facility is located in an area designated attainment for all pollutants.

Since the facility is not one of those contained in Table 500-1, F.A.C. Chapter 17-2, the VOC threshold for triggering new source review pursuant to F.A.C. Rule 17-2.500(5), is 250 TPY.

The following table presents the net projected potential pollutant emissions associated with the proposed modification:

Source	Net Potential Pollutant Emissions (TPY)	
	VOC	Acid
Building 54	-1.7	-0.2
Building 55	+0.7	
Building 57	+1.0	
Building 59		+0.2
Total:	0.0	0.0

Note: o Allowed continuous operation (i.e., 8760 hrs/yr).
 o Building 54 has a decrease in the allowable/potential VOC emissions of 1.7 TPY and is not creditable.

The following table presents the projected potential pollutant emissions from the current existing facility:

Source	Potential Pollutant Emissions (TPY)		
	VOC	SO ₂	H ₂ S
Building 4	14.3		
51	34.7		
54	75.5		
55	0.3	(fugitive)	
57	2.0		
58	7.6		
59	8.4		
60	2.6		
61	0.3		
62	1.0		
63	13.5		
IGWS: Flare System		43.8	0.35
Total:	160.2	43.8	0.35

Note: o Allowed continuous operation (i.e., 8760 hrs/yr).

The following table presents the projected potential pollutant emissions from the facility after the modification:

Table 3

Source	Potential Pollutant Emissions (TPY)		
	VOC	SO ₂	H ₂ S
Building 4	14.3		
51	34.7		
54	73.8		
55	1.0	(fugitive)	
57	3.0		
58	7.6		
59	8.4		
60	2.6		
61	0.3		
62	1.0		
63	13.5		
IGWS: Flare System		43.8	0.35
Total:	160.2	43.8	0.35

Note: o Allowed continuous operation (i.e., 8760 hrs/yr).

Based on the tables, the proposed project is a minor modification (+0.0 total TPY) to a major facility for VOC due to source potential emission increases and decreases, which will require changes in the federally enforceable conditions of each source's current permit. Therefore, the potential pollutant emissions shall be subject to review in accordance with F.A.C. Rule 17-2.520, Sources Not Subject to PSD or Nonattainment Requirements.

Since there is no specific emission limiting standard contained in F.A.C. Rule 17-2.600 nor are there any standards of performance for new stationary sources contained in F.A.C. Rule 17-2.660, the modification to each source/building will be permitted in accordance with F.A.C. Rule 17-2.620, General Pollutant Emission Limiting Standards.

In F.A.C. Rule 17-2.620(1)(a), no person shall store, pump, handle, process, load, unload or use in any process or installation volatile organic compounds or organic solvents without applying known and existing vapor emission control devices or systems deemed necessary and ordered by the Department. Pursuant to F.A.C. Rule 17-2.620(2), no person shall cause, suffer, allow or permit the discharge of air pollutants which cause or contribute to an objectionable odor. Objectionable odor is defined as any odor present in the outdoor atmosphere, which by itself or in combination with other odors, is or may be harmful or injurious to

human health or welfare, which unreasonably interferes with the comfortable use and enjoyment of life or property, or which creates a nuisance according to F.A.C. Rule 17-2.100, Definitions-Objectionable Odor.

The sources/buildings are subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation-Problems.

III. Summary of Emissions

A. Emission Limitations

The regulated pollutant emissions from Buildings 54, 55, 57 and 59, are VOC. Various acid gases are also being emitted during the manufacturing operations in these buildings. There are no specific emission limiting standards for these specific acids; however, the acid vapors will be scrubbed to reduce emissions.

The following table presents the resulting project's allowable VOC emissions and potential acid vapor emissions from each source/building:

Table 4

Source	Maximum Allowable Pollutant Emissions/Limitations VOC	Potential Acid Emissions
Building 54	73.8	9.7
Building 55	1.0	
Building 57	3.0	
Building 59		0.3

Note: o Allowed continuous operations (i.e., 8760 hrs/yr).

The permitted emissions/limitations are in compliance with all requirements of F.A.C. Chapters 17-2 and 17-4.

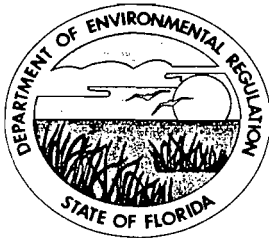
B. Air Quality Impacts

From a technical review of the application packages, which shows no net change in the potential pollutant emissions, an air quality analysis is not required.

IV. Conclusion

Based on the information provided by Harris Semiconductor, the Department has reasonable assurance that the proposed modifications to Buildings/sources 54, 55, 57 and 59, which shows no net change in the facility's total potential pollutant emissions (i.e., VOC and acid), but requires a change in the federally enforceable conditions of each source's current permit (i.e., modification), as described in this evaluation, and subject to the conditions proposed herein, will not cause or contribute to a violation of any air quality standard, PSD increment, or any other technical provision of Chapter 17-2 of the Florida Administrative Code.

Preston Lewis
41755



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-203985
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 54 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 54, which is an existing source that utilizes hood type work stations for the manufacture of semiconductors, to permit a decrease in the potential acid and the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control systems are:

- o F54S01: a Beverly Pacific 50,000 scfm (43,141 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. PS-50HT;
- o F54S02: a Harrington 17,000 scfm (16,000 acfm) horizontal cross-flow wet scrubber, using PVC packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. ECH 66-9PBS; and,
- o F54S03: a Beverly Pacific 30,000 scfm (29,000 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator, for VOC and acid vapor removal; Model No. PS-24HT.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36

- o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent Stripping → Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

- a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;
- b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the dates analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and,
 - the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 54 is 73.8 tons per year.

2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.

3. Continuous operation shall be allowed (i.e., 8760 hours per year).

4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).

5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.

6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 54.

7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
- b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
- d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 54.
9. The source/Building No. 54 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 9.7 TPY.
11. Building No. 54 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-203985
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this _____ day
of _____, 1992

**STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION**

STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-202415
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 55 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 55, which is an existing source for the collection, short term storage, and shipping point for waste chemicals from the facility, to permit an increase in the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control system is:

- o F55S01: a Tri-Mer Corp. 9,500 scfm (7,500 acfm) horizontal counter-flow wet scrubber, using a polypropylene filter pack, and with a mist eliminator, for VOC and acid vapor removal; Model No. F/W 3.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36

- o Cold Solvent Cleaning/Stripping 4-01-003-99 Tons VOC/solvent Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

- a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;
- b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the dates analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and,
 - the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 55 is 1.0 tons per year.

2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.

3. Continuous operation shall be allowed (i.e., 8760 hours per year).

4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).

5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.

6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 55.

7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
- b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
- d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-202415
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 55.
9. The source/Building No. 55 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 0.1 TPY.
11. Building No. 55 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

PERMITTEE:
Harris Semiconductor

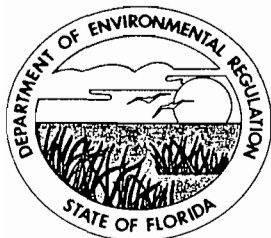
Permit Number: AC 05-202415
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this _____ day
of _____, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-205848
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W

Project: Building 57 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 57, which is an existing source whose primary manufacturing operations are soldering and plating of integrated circuit parts, to permit an increase in the potential/allowable VOC (volatile organic compounds/organic solvents) emissions. The scrubber control system is:

- o F57S01: a Tri-Mer Corp. 13,500 scfm (9,328 acfm) horizontal counter-flow wet scrubber, using a polypropylene filter pack, and with a mist eliminator, for VOC and acid vapor removal; Model No. F/W 5.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36
o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent
Stripping Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;

b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,

c. Records of monitoring information shall include:

- the date, exact place, and time of sampling or measurements;
- the person responsible for performing the sampling or measurements;
- the dates analyses were performed;
- the person responsible for performing the analyses;
- the analytical techniques or methods used; and,
- the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 57 is 2.0 tons per year.

2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.

3. Continuous operation shall be allowed (i.e., 8760 hours per year).

4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).

5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.

6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 57.

7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
- b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
- d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205848
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 57.
9. The source/Building No. 57 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 0.2 TPY.
11. Building No. 57 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

PERMITTEE:
Harris Semiconductor

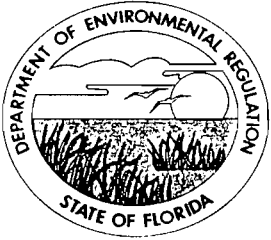
Permit Number: AC 05-205848
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this _____ day
of _____, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

Permittee:
Harris Semiconductor
P. O. Box 883
Melbourne, FL 32902-0883

Permit Number: AC 05-205849
Expiration Date: July 31, 1992
County: Brevard
Latitude/Longitude: 28°01'20"N
80°36'10"W
Project: Building 59 Modification

This permit is issued under the provisions of Chapter 403, Florida Statutes, Florida Administrative Code (F.A.C.) Chapters 17-2 and 17-4, and 40 CFR (July, 1990 version). The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawings, plans, and other documents attached hereto or on file with the Department and made a part hereof and specifically described as follows:

For the modification of Building 59, which is an existing source used for the manufacture of semiconductors, to permit an increase in the potential acid emissions. The scrubber control and exhaust systems are:

Reliability Shop:

- o F59S01: a Beverly Pacific 40,000 scfm (30,838 acfm) horizontal cross-flow wet scrubber, using polypropylene packing, and with a PVC mist eliminator for acid vapor removal; Model No. PS-40HT;
- o F59S02: a Beverly Pacific 20,000 scfm (10,972 acfm) vertical counter-current wet scrubber, using polypropylene packing, with a PVC mist eliminator, for VOC (volatile organic compounds/organic solvents) vapor removal; Model No. PS-24VT; and,

Probe Card Repair Shop:

- o F59E04: an exhaust fan.

The building/source is located at the permittee's existing facility located on Palm Bay Road in the City of Palm Bay. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

The Source Classification Codes are: Major Group 36

- o Cold Solvent Cleaning/ 4-01-003-99 Tons VOC/solvent Stripped Consumed

The source shall be constructed in accordance with the permit application, plans, documents, amendments and drawings, except as otherwise noted in the General and Specific Conditions.

Attachments are listed below:

1. Application to Construct/Modify Air Pollution Sources, DER Form 17-2.202(1), received October 24, 1991.
2. Technical Evaluation and Preliminary Determination dated January 10, 1992.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth in this permit are "Permit Conditions" and are binding and enforceable pursuant to Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is placed on notice that the Department will review this permit periodically and may initiate enforcement action for any violation of these conditions.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the Department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Neither does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit is not a waiver of or approval of any other Department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute State recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the State. Only the Trustees of the Internal Improvement Trust Fund may express State opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, or plant life, or property caused by the construction or operation of this permitted source, or from penalties therefore; nor does it allow the permittee to cause pollution in contravention of Florida Statutes and Department rules, unless specifically authorized by an order from the Department.

6. The permittee shall properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by Department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by Department rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

7. The permittee, by accepting this permit, specifically agrees to allow authorized Department personnel, upon presentation of credentials or other documents as may be required by law and at a reasonable time, access to the premises, where the permitted activity is located or conducted to:

- a. Have access to and copy any records that must be kept under the conditions of the permit;
- b. Inspect the facility, equipment, practices, or operations regulated or required under this permit; and,
- c. Sample or monitor any substances or parameters at any location reasonably necessary to assure compliance with this permit or Department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately provide the Department with the following information:

- a. a description of and cause of non-compliance; and,
- b. the period of noncompliance, including dates and times; or, if not corrected, the anticipated time the non-compliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the non-compliance.

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the Department for penalties or for revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source which are submitted to the Department may be used by the Department as evidence in any enforcement case involving the permitted source arising under the Florida Statutes or Department rules, except where such use is prescribed by Sections 403.73 and 403.111, Florida Statutes. Such evidence shall only be used to the extent it is consistent with the Florida Rules of Civil Procedure and appropriate evidentiary rules.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

10. The permittee agrees to comply with changes in Department rules and Florida Statutes after a reasonable time for compliance, provided, however, the permittee does not waive any other rights granted by Florida Statutes or Department rules.

11. This permit is transferable only upon Department approval in accordance with Florida Administrative Code Rules 17-4.120 and 17-30.300, F.A.C., as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the Department.

12. This permit or a copy thereof shall be kept at the work site of the permitted activity.

13. The permittee shall comply with the following:

- a. Upon request, the permittee shall furnish all records and plans required under Department rules. During enforcement actions, the retention period for all records will be extended automatically unless otherwise stipulated by the Department;
- b. The permittee shall hold at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation) required by the permit, copies of all reports required by this permit, and records of all data used to complete the application for this permit. These materials shall be retained at least three years from the date of the sample, measurement, report, or application unless otherwise specified by Department rule; and,
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the dates analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and,
 - the results of such analyses.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

GENERAL CONDITIONS:

14. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds/organic solvents) emissions from Building No. 59 is 8.4 tons per year.
2. The VOC vapor and acid gas exhaust scrubber systems must be operating properly during the working hours.
3. Continuous operation shall be allowed (i.e., 8760 hours per year).
4. Objectionable odors shall not be allowed off plant property pursuant to F.A.C. Rule 17-2.620(2).
5. An inspection and maintenance plan shall be submitted to the DER's Central District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC losses from leaks and equipment malfunctions.
6. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC emissions limit for Building 59.
7. Each scrubber system's efficiency and actual VOC emissions shall be established by a sampling and analysis program, which includes:
 - a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Method 25A, pursuant to F.A.C. Rule 17-2.700 and 40 CFR 60, Appendix A;
 - b) the DER's Central District office shall receive at least 15 days notice in writing prior to sampling;
 - c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed;
 - d) the efficiency of each control system shall be established by tests (inlet and outlet) once every five years for operation permit renewal; and,

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

- e) the annual VOC emissions shall be calculated using actual emissions data derived from stack test sampling results and the actual operating hours for the affected source/building.
8. This permit will supercede all other permits previously issued on this source/Building No. 59.
9. The source/Building No. 59 is subject to all applicable provisions of F.A.C. Chapters 17-2 and 17-4 and 40 CFR (July, 1990 version).
10. Projected potential acid emissions are 0.3 TPY.
11. Building No. 59 is subject to the applicable provisions of F.A.C. Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; and, 17-4.130: Plant Operation - Problems.
12. Any modification pursuant to F.A.C. Rule 17-2.100, Definitions-Modification, shall be submitted to the DER's Central District office and Bureau of Air Regulation (BAR) office for approval.
13. The permittee, for good cause, may request that this construction permit be extended. Such a request shall be submitted to the DER's BAR prior to 60 days before the expiration of the permit (F.A.C. Rule 17-4.090).
14. An application for an operation permit must be submitted to the DER's Central District office at least 90 days prior to the expiration date of this construction permit. To properly apply for an operation permit, the applicant shall submit the appropriate application form, fee, certification that construction was completed noting any deviations from the conditions in the construction permit, and compliance test reports as required by this permit (F.A.C. Rules 17-4.055 and 17-4.220).

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-205849
Expiration Date: July 31, 1992

SPECIFIC CONDITIONS:

Issued this _____ day
of _____, 1992

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

STEVE SMALLWOOD, P.E., Director
Division of Air Resources
Management

ATTACHMENTS AVAILABLE UPON REQUEST

DEPARTMENT OF ENVIRONMENTAL REGULATION

#1,000pd.
10-24-91
Receipt #180709

RECEIVED

WIN TOWERS OFFICE BUILDING
2609 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241

OCT 24 1991

Bureau of
Air Regulation



AC05-203985

BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

APPLICATION TO OPERATE/CONSTRUCT AIR POLLUTION SOURCES

SOURCE TYPE: Stationary [] New¹ [X] Existing¹

APPLICATION TYPE: [] Construction [X] Operation [X] Modification

COMPANY NAME: Harris Semiconductor COUNTY: Brevard

Identify the specific emission point source(s) addressed in this application (i.e. Lime Kiln No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired) Bldgs. 54, 55, 57, 59

SOURCE LOCATION: Street Palm Bay Road City Palm Bay

UTM: East 17-538700 North 17-3100900

Latitude 28 ° 01 ' 20 "N Longitude 80 ° 36 ' 10 "W

APPLICANT NAME AND TITLE: John R. Steiner, Director Environmental & Facilities

APPLICANT ADDRESS: P.O. Box 883, Melbourne, FL 32901

SECTION I: STATEMENTS BY APPLICANT AND ENGINEER

A. APPLICANT

I am the undersigned owner or authorized representative* of Harris Semiconductor

I certify that the statements made in this application for a modified permit are true, correct and complete to the best of my knowledge and belief. Further, I agree to maintain and operate the pollution control source and pollution control facilities in such a manner as to comply with the provision of Chapter 403, Florida Statutes, and all the rules and regulations of the department and revisions thereof. I also understand that a permit, if granted by the department, will be non-transferable and I will promptly notify the department upon sale or legal transfer of the permitted establishment.

*Attach letter of authorization

Signed: John R. Steiner
John R. Steiner, Director Environmental & Facilities
Name and Title (Please Type)

Date: 10/31/91 Telephone No. (407) 724-7078

B. PROFESSIONAL ENGINEER REGISTERED IN FLORIDA (where required by Chapter 471, F.S.)

This is to certify that the engineering features of this pollution control project have been designed/examined by me and found to be in conformity with modern engineering principles applicable to the treatment and disposal of pollutants characterized in the permit application. There is reasonable assurance, in my professional judgment, that

¹ See Florida Administrative Code Rule 17-2.100(57) and (104)

the pollution control facilities, when properly maintained and operated, will discharge an effluent that complies with all applicable statutes of the State of Florida and the rules and regulations of the department. It is also agreed that the undersigned will furnish, if authorized by the owner, the applicant a set of instructions for the proper maintenance and operation of the pollution control facilities and, if applicable, pollution sources.



Signed Scott W McClarty

Scott W. McClarty, P.E.

Name (Please Type)

Harris Semiconductor

Company Name (Please Type)

P.O. Box 883, Melbourne, FL 32901

Mailing Address (Please Type)

Florida Registration No. 34468 Date: 10/21/91 Telephone No. (407) 729-4655

SECTION II: GENERAL PROJECT INFORMATION

1. Describe the nature and extent of the project. Refer to pollution control equipment, and expected improvements in source performance as a result of installation. State whether the project will result in full compliance. Attach additional sheet if necessary.

This is a modification to the construction permits AC 05-190800 (Bldg. 54);

AC 05-190799 (Bldg. 55); AC 05-189178 (Bldg. 57); AC 05-180707 (Bldg.59)

See Insert A for further information

2. Schedule of project covered in this application (Construction Permit Application Only)

Start of Construction N/A Completion of Construction _____

3. Costs of pollution control system(s): (Note: Show breakdown of estimated costs only for individual components/units of the project serving pollution control purposes. Information on actual costs shall be furnished with the application for operation permit.)

N/A

4. Indicate any previous DER permits, orders and notices associated with the emission point, including permit issuance and expiration dates.

See Insert B

INSERT A

The proposed modification to the construction permits for Buildings 54, 55, 57 and 59 is intended to adjust the emission limits of VOCs or Acids, as described below, without changing the overall site emissions.

This modification was engineered as a result of the last two sets of monitoring data collected for this site. The monitoring indicated a significant decrease in VOC and acid emissions from Building 54 due to certain chemical substitutions and higher than expected VOC emissions from Building 57 and Acid emissions from Building 59.

Consequently, it was deemed necessary to request for an additional buffer to the emission limits for Buildings 57 (VOCs) and 59 (Acids) to accommodate for fluctuations in the production activities and chemical usage. Similarly, we request for an additional buffer to the VOC emissions from Building 55. The overall increase in emissions is proposed to be offset by a proportionate decrease in the Building 54 emissions.

Specifically, the modification submittal proposes for an increase/reduction in the VOC or Acid emissions as follows:

- Bldg 55, VOC emissions from 0.3 tons to 1.0 ton a year.
- Bldg 57, VOC emissions from 2.0 tons to 3.0 tons a year.
- Bldg 59, Acid emissions from 0.1 tons to 0.3 tons a year.
- Bldg 54, VOC emissions from 75.5 tons to 73.8 tons a year.
- Bldg 54 Acid emissions from 9.9 tons to 9.7 tons a year.

INSERT B

Building 54: AO 05-65408 issued 5/3/83; exp. 5/2/88
AO 05-115804 issued 5/20/86; exp. 5/22/91
AC 05-147321 issued 10/25/88; exp. 6/30/91

Building 55: AC 05-104523 issued 1/14/86; exp. 6/30/86
AC 05-164544 issued 10/26/89; exp. 6/30/91

Building 57: AC 05-104522 issued 1/14/86; exp. 6/30/86
AC 05-161706 issued 5/26/89; exp. 6/30/91

Building 59: AC 05-104521 issued 1/15/86; exp. 6/30/86
AC 05-104527 issued 1/15/86; exp. 4/1/86
AC 05-150794 issued 3/31/89; exp. 12/5/89
AC 05-174445 issued 3/27/90; exp. 1/31/91

E. Requested permitted equipment operating time: hrs/day 24 ; days/wk 7 ; wks/yr 52 ;
if power plant, hrs/yr _____; if seasonal, describe: _____

F. If this is a new source or major modification, answer the following questions.
(Yes or No)

1. Is this source in a non-attainment area for a particular pollutant? No
 - a. If yes, has "offset" been applied? _____
 - b. If yes, has "Lowest Achievable Emission Rate" been applied? _____
 - c. If yes, list non-attainment pollutants. _____
2. Does best available control technology (SACT) apply to this source?
If yes, see Section VI. No
3. Does the State "Prevention of Significant Deterioration" (PSD)
requirement apply to this source? If yes, see Sections VI and VII. No
4. Do "Standards of Performance for New Stationary Sources" (NSPS)
apply to this source? No
5. Do "National Emission Standards for Hazardous Air Pollutants"
(NESHAP) apply to this source? No
- H. Do "Reasonably Available Control Technology" (RACT) requirements apply
to this source? No
 - a. If yes, for what pollutants? _____
 - b. If yes, in addition to the information required in this form,
any information requested in Rule 17-2.650 must be submitted.

Attach all supportive information related to any answer of "Yes". Attach any justifi-
cation for any answer of "No" that might be considered questionable. .

SECTION III: AIR POLLUTION SOURCES & CONTROL DEVICES (Other than Incinerators)

A. Raw Materials and Chemicals Used in your Process, if applicable:

Description	Contaminants		Utilization Rate - lbs/hr	Relate to Flow Diagram
	Type	% Wt		
---SEE ATTACHMENT C---	C---			

B. Process Rate, if applicable: (See Section V, Item 1)

- Total Process Input Rate (lbs/hr): not applicable
- Product Weight (lbs/hr): not applicable

C. Airborne Contaminants Emitted: (Information in this table must be submitted for each emission point, use additional sheets as necessary)

Name of Contaminant	Emission ¹		Allowed Emission Rate per Rule 17-2	Allowable ³ Emission lbs/hr	Potential ⁴ Emission		Relate to Flow Diagram
	Maximum lbs/hr	Actual T/yr			lbs/yr	T/yr	
---SEE ATTACHMENT B---							

¹See Section V, Item 2.

²Reference applicable emission standards and units (e.g. Rule 17-2.600(5)(b)2. Table II, E.(1) - 0.1 pounds per million BTU heat input)

³Calculated from operating rate and applicable standard.

⁴Emission, if source operated without control (See Section V, Item 3).

J. Control Devices: (See Section V, Item 4)

Name and Type (Model & Serial No.)	Contaminant	Efficiency	Range of Particles Size Collected (in microns) (If applicable)	Basis for Efficiency (Section V Item 5)
---SEE ATTACHMENT D---				

E. Fuels

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	avg/hr	max./hr	

*Units: Natural Gas--MMCF/hr; Fuel Oils--gallons/hr; Coal, wood, refuse, other--lbs/hr.

Fuel Analysis:

Percent Sulfur: _____ Percent Ash: _____

Density: _____ lbs/gal Typical Percent Nitrogen: _____

Heat Capacity: _____ BTU/lb _____ BTU/gal

Other Fuel Contaminants (which may cause air pollution): _____

F. If applicable, indicate the percent of fuel used for space heating.

Annual Average _____ Maximum _____

G. Indicate liquid or solid wastes generated and method of disposal.

Waste water from air scrubbers is discharged to on-site Waste Water Treatment
Plant --discharge to deepwell under UIC- Permit # UC05-126519.

-----SEE ATTACHMENT D-----

H. Emission Stack Geometry and Flow Characteristics (Provide data for each stack):

Stack Height: _____ ft. Stack Diameter: _____ ft.
 Gas Flow Rate: _____ ACFM _____ DSCFM Gas Exit Temperature: _____ °F.
 Water Vapor Content: _____ % Velocity: _____ FPS

SECTION IV: INCINERATOR INFORMATION
 not applicable

Type of Waste	Type 0 (Plastics)	Type I (Rubbish)	Type II (Refuse)	Type III (Garbage)	Type IV (Pathological)	Type V (Liq. & Gas By-prod.)	Type VI (Solid By-prod.)
Actual lb/hr Incinerated							
Uncontrolled (lbs/hr)							

Description of Waste _____
 Total Weight Incinerated (lbs/hr) _____ Design Capacity (lbs/hr) _____
 Approximate Number of Hours of Operation per day _____ day/wk _____ wks/yr. _____
 Manufacturer _____
 Date Constructed _____ Model No. _____

	Volume (ft) ³	Heat Release (BTU/hr)	Fuel		Temperature (°F)
			Type	BTU/hr	
Primary Chamber					
Secondary Chamber					

Stack Height: _____ ft. Stack Diameter: _____ Stack Temp. _____
 Gas Flow Rate: _____ ACFM _____ DSCFM* Velocity: _____ FPS

*If 50 or more tons per day design capacity, submit the emissions rate in grains per standard cubic foot dry gas corrected to 50% excess air.

Type of pollution control device: Cyclone Wet Scrubber Afterburner
 Other (specify) _____

Brief description of operating characteristics of control devices: _____

Ultimate disposal of any effluent other than that emitted from the stack (scrubber water, ash, etc.):

NOTE: Items 2, 3, 4, 6, 7, 8, and 10 in Section V must be included where applicable.

SECTION V: SUPPLEMENTAL REQUIREMENTS

Please provide the following supplements where required for this application.

1. Total process input rate and product weight -- show derivation [Rule 17-2.100(127)]
2. To a construction application, attach basis of emission estimate (e.g., design calculations, design drawings, pertinent manufacturer's test data, etc.) and attach proposed methods (e.g., FR Part 60 Methods 1, 2, 3, 4, 5) to show proof of compliance with applicable standards. To an operation application, attach test results or methods used to show proof of compliance. Information provided when applying for an operation permit from a construction permit shall be indicative of the time at which the test was made.
3. Attach basis of potential discharge (e.g., emission factor, that is, AP42 test).
4. With construction permit application, include design details for all air pollution control systems (e.g., for baghouse include cloth to air ratio; for scrubber include cross-section sketch, design pressure drop, etc.)
5. With construction permit application, attach derivation of control device(s) efficiency. Include test or design data. Items 2, 3 and 5 should be consistent: actual emissions = potential (1-efficiency).
6. An 8 1/2" x 11" flow diagram which will, without revealing trade secrets, identify the individual operations and/or processes. Indicate where raw materials enter, where solid and liquid waste exit, where gaseous emissions and/or airborne particles are evolved and where finished products are obtained.
7. An 8 1/2" x 11" plot plan showing the location of the establishment, and points of airborne emissions, in relation to the surrounding area, residences and other permanent structures and roadways (Example: Copy of relevant portion of USGS topographic map).
8. An 8 1/2" x 11" plot plan of facility showing the location of manufacturing processes and outlets for airborne emissions. Relate all flows to the flow diagram.

9. The appropriate application fee in accordance with Rule 17-4.05. The check should be made payable to the Department of Environmental Regulation.
10. With an application for operation permit, attach a Certificate of Completion of Construction indicating that the source was constructed as shown in the construction permit.

SECTION VI: BEST AVAILABLE CONTROL TECHNOLOGY

A. Are standards of performance for new stationary sources pursuant to 40 C.F.R. Part 60 applicable to the source?

Yes No

Contaminant	Rate or Concentration

B. Has EPA declared the best available control technology for this class of sources (if yes, attach copy)

Yes No

Contaminant	Rate or Concentration

C. What emission levels do you propose as best available control technology?

Contaminant	Rate or Concentration

D. Describe the existing control and treatment technology (if any).

- | | |
|---------------------------|--------------------------|
| 1. Control Device/System: | 2. Operating Principles: |
| 3. Efficiency:* | 4. Capital Costs: |

*Explain method of determining

5. Useful Life:

6. Operating Costs:

7. Energy:

8. Maintenance Cost:

9. Emissions:

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

10. Stack Parameters

- a. Height: ft.
- b. Diameter: ft.
- c. Flow Rate: ACFM
- d. Temperature: °F.
- e. Velocity: FPS

E. Describe the control and treatment technology available (As many types as applicable, use additional pages if necessary).

1.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Cost:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

2.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Cost:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:

¹Explain method of determining efficiency.

²Energy to be reported in units of electrical power - KWH design rate.

- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

3.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Cost:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

4.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Costs:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

F. Describe the control technology selected:

- 1. Control Device:
- 2. Efficiency:¹
- 3. Capital Cost:
- 4. Useful Life:
- 5. Operating Cost:
- 6. Energy:²
- 7. Maintenance Cost:
- 8. Manufacturer:
- 9. Other locations where employed on similar processes:
- a. (1) Company:
- (2) Mailing Address:
- (3) City:
- (4) State:

Explain method of determining efficiency.

Energy to be reported in units of electrical power - KWH design rate.

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant	Rate or Concentration

(8) Process Rate:¹

b. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant	Rate or Concentration

(8) Process Rate:¹

10. Reason for selection and description of systems:

¹Applicant must provide this information when available. Should this information not be available, applicant must state the reason(s) why.

SECTION VII - PREVENTION OF SIGNIFICANT DETERIORATION

A. Company Monitored Data

1. _____ no. sites _____ TSP _____ () SO₂* _____ Wind spd/dir

Period of Monitoring _____ / _____ / _____ to _____ / _____ / _____
month day year month day year

Other data recorded _____

Attach all data or statistical summaries to this application.

Specify bubbler (B) or continuous (C).

2. Instrumentation, Field and Laboratory

- a. Was instrumentation EPA referenced or its equivalent? [] Yes [] No
- b. Was instrumentation calibrated in accordance with Department procedures?
[] Yes [] No [] Unknown

B. Meteorological Data Used for Air Quality Modeling

- 1. _____ Year(s) of data from _____ / _____ / _____ to _____ / _____ / _____
month day year month day year
- 2. Surface data obtained from (location) _____
- 3. Upper air (mixing height) data obtained from (location) _____
- 4. Stability wind rose (STAR) data obtained from (location) _____

C. Computer Models Used

- 1. _____ Modified? If yes, attach description.
- 2. _____ Modified? If yes, attach description.
- 3. _____ Modified? If yes, attach description.
- 4. _____ Modified? If yes, attach description.

Attach copies of all final model runs showing input data, receptor locations, and principle output tables.

D. Applicants Maximum Allowable Emission Data

Pollutant	Emission Rate
TSP	_____ grams/sec
SO ²	_____ grams/sec

E. Emission Data Used in Modeling

Attach list of emission sources. Emission data required is source name, description of point source (on NEDS point number), UTM coordinates, stack data, allowable emissions, and normal operating time.

F. Attach all other information supportive to the PSD review.

G. Discuss the social and economic impact of the selected technology versus other applicable technologies (i.e., jobs, payroll, production, taxes, energy, etc.). Include assessment of the environmental impact of the sources.

H. Attach scientific, engineering, and technical material, reports, publications, journals, and other competent relevant information describing the theory and application of the requested best available control technology.

ATTACHMENT A.
PROCESS DESCRIPTION

PROCESS DESCRIPTION BUILDING 54

Building 54 is a wafer fabrication facility. The second floor of the two-story building houses two clean room modules. Both fabrication areas employ a series of manufacturing procedures referred to as layering, patterning, doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

In the controlled environment of the fabrication clean rooms, wafer surfaces first undergo acid and/or solvent cleaning, followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process, the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "aligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers are hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques.

In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Additional material may be layered on the wafer surface in diffusion, plasma and crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation.

Wet stations that house vats containing a variety of acid and caustic compounds are located throughout the clean rooms. Storage cabinets safely hold virgin chemicals until they are ready for use. The first floor of the building contains exhausted gas cabinets that supply process gases to the 'fab' operations.

The exhaust system for the Building is divided into two sections. The west portion of the Building is exhausted to the wet scrubber system F54S01 at ground level. The east portion of the Building exhaust is ducted to a common line that divides into two wet scrubber systems F54S03 and F54S04 located also at ground level (see Attachment E). Also on the east side of building 54 is a non-scrubbed exhaust fan F54E17 that handles air flow from several aligners, furnace source cabinets, and gas cabinets.

**PROCESS DESCRIPTION
BUILDING 55**

Building 55 is the collection, short term storage, and shipping point for waste chemicals from the various areas of the facility. Activities which are exhausted, involve the handling of empty, capped glass and plastic solvent bottles which are brought to the Building in gondolas or 'bins'.

The Building houses six exhausted wet stations/operations. Two stations are used for acid bottle washing, and another station is used on an 'as needed basis' to control the release of chemicals from broken, deteriorated, or damaged 'bubbler' containers which cannot be safely returned to the vendor. These 'bubblers' supply reactive gases to the chemical vapor deposition process in the wafer fabrication areas (these areas are located in other buildings on the site). Another station is used for a solvent stripper bottle washing. This station is pending approval as an amendment to the permit AC 05-190799.

The Building also houses two bottle crushers for the remaining empty solvent bottles as well as the acid washed and the stripper washed bottles. This operation was a source of fugitive solvent emissions and recently was permitted to be exhausted as an amendment to the permit AC 05-190799.

The above mentioned stations and operations are exhausted to scrubber number F55S01, which is located on the roof of the building. Information on this scrubber is submitted in Attachment D, control equipment information, and in Attachment E, scrubber location maps. The fume scrubber is operating continuously but emissions are exhausted only when there is chemical activity under the hooded wet stations/operations.

The waste solvent chemicals brought to Building 55 are used process chemicals from the manufacturing operations at the plant. The waste solvents are brought in closed containers and are stored as such for a short time prior to lab-packing and disposal offsite. Consequently, this operation produces negligible amounts of emissions.

PROCESS DESCRIPTION
BUILDING 57

The primary manufacturing operations in Building 57 are Soldering and Plating of integrated circuit parts. The Soldering process involves two wave solder machines, a solder bath system, and an aqueous post cleaning system.

The Plating process involves a series of wet stations with acid vats and a water rinse station. No covers are used on the vats. Integrated circuits that previously underwent a baking process are acid etched at an elevated temperature to remove an oxidized layer.

Exhausted equipment includes wave soldering machines, an aqueous post cleaning system, wet stations, chemical storage cabinets, and a degreaser.

Scrubber number F57S01 treats acidic and corrosive contaminated exhaust generated from the above mentioned equipment. The scrubber is located on the roof of the building. Location maps are included in Attachment E of this submittal. Additional information on the scrubber is included in Attachment D.

PROCESS DESCRIPTION - BUILDING 59

Building 59 houses a wafer fabrication facility on the first floor. The wafer fabrication area employs a series of manufacturing procedures referred to as layering, patterning, doping, and heating. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

In the controlled environment of the fabrication clean room, wafer surfaces first undergo acid and/or solvent cleaning, followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process, the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "aligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers are hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques. In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Fumes from the vapor deposition furnaces are oxidized in 'burn boxes.' The oxidized gases are then exhausted to scrubber systems. Additional material may be layered on the wafer surface in vapor and crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation. Thirteen exhausted wet stations that house vats containing a variety of acid and caustic compounds are in the fabrication facility. Five of these stations contain solvents; one of which is heated.

To the east of the 'fab' is a probe card repair shop. Four solvent stations are presently employed.

The ground floor houses a process equipment support room that contains gas cabinets, chemical storage cabinets, vacuum pumps and drains. These exhausted units service the process equipment which safely hold virgin chemicals until they are ready for use. Gas cabinets house cylinders that supply process gases to the fab operations. In addition, several waste collection areas are exhausted. The ground floor also houses the site's distilled water plant, and a mechanical equipment storage area.

The aluminum etching equipment of the fab is exhausted to two gas trap units in conjunction with two dry vacuum pumps. The gas traps are located on the ground floor of the Building. The gas traps are the Ebara GTE-3 units along with the Ebara 50x20 Dry Vacuum Pumps (see Attachment D, Control Equipment).

ATTACHMENT B.
AIR EMISSIONS

SOLVENT MONITORING
BUILDING 54, BUILDING 55, BUILDING 57, BUILDING 59

Solvent monitoring work was performed on the Buildings 54, 55, 57 and 59 scrubber systems in June and October of 1990 and in January of 1991. The tests conducted were EPA Method 25A (flame ionization detection) and EPA Methods 1-4 to measure moisture and flow data for the outlet. The results are included in the following tables of this application submittal.

The monitoring was performed over an 8 hour interval when full production was occurring. The data was corrected for background noise that is normally present in the ambient air. The results were derived using 1990 actual production hours. The actual number of operating hours for calendar year 1991 is recorded monthly for each Building and will be available at the end of the year.

As mentioned in the application section of this submittal, the 1990 and 1991 monitoring data indicate a significant reduction in the VOC/Solvent emissions from Building 54 and higher than expected from Building 57.

Furthermore, based on 1988 monitoring work on a number of scrubbers at this site, it was determined that emissions during non production hours equaled 18.3 % of the emissions occurring during production hours. Emission reduction efforts such as chemical substitutions, shorter times in chemical use, covered solvent baths, etc. showed a reduction in the overall emissions at this site which further indicates the non-production emissions are lower. Assuming 'worst case' conditions, the additional emissions appear to exceed the projected potential emissions for Building 57. The attached tables show the 1990 and 1991 monitored production emissions, the calculated non-production emissions and the combined emissions for Buildings 54 and 57 as well as the latest fugitive emission calculations for Building 55.

Consequently, we request that an additional buffer is considered to accommodate for fluctuations in production activities and chemical usage. In addition, we request for an additional buffer to the air emissions for Building 55. Therefore, we request for the following changes in potential emissions:

An increase of the Building 57 projected potential VOC emissions from 2.0 to 3.0 tons per year.

An increase of the Building 55 projected potential VOC emissions from to 0.3 to 1.0 tons per year.

A decrease of the Building 54 projected potential VOC emissions from 75.5 to 73.8 tons per year.

The proposed adjustments will not change the overall solvent emissions for the site.

Exhausted equipment on the ground floor and in the wafer fabrication area is ducted to one of two scrubbers; acid vapors are vented to scrubber number F59S01, while solvent exhaust streams are ducted to scrubber number F59S02. Both systems reside on the site grounds directly outside the west wall of the building (see scrubber location maps attached.)

Probe card repair shop equipment is ducted to exhaust fan no. F59E04, which is housed in the building on the ground floor (east side; see location map.)

The Building also houses the Reliability lab on the first floor to the west of the fabrication area. In Reliability, integrated circuits are tested for a wide variety of parameters including tolerance to temperature and humidity changes, endurance, and electrical conductivity. Two solvent stations and four acid stations were added. The wet benches are exhausted to the existing scrubber systems described above.

SUMMARY OF 1990 AND 1991 ANNUAL MONITORING RESULTS ON VOC/SOLVENT EMISSIONS EXPRESSED AS PROPANE. THIS DATA IS BASED ON ACTUAL OPERATING HOURS FOR THE CALENDAR YEAR 1990. BUILDING 55 FUGITIVE EMISSIONS ARE BASED ON ENGINEERING CALCULATIONS.

1990 MONITORING EMISSION DATA

TEST DATE	BLDG #	1990 PRODUCT. SCHEDULE (HRS/YR)	AVG VOC EMISS. (LBS/HR)	PRODUCT. VOC EMISS. (TONS/YR)	NON-PRODUCT. VOC EMISS. 18.3% OF PRODUCT. EMISS. (TONS/YR)	1990 TOTAL EMISSIONS (TONS/YR)
06/90	54	6468	5.83	18.85	3.45	22.30
06/90	55	2500	N/A	0.24 (FUG. EMISS.)	N/A	0.24
06/90	57	6936	0.23	0.80	0.15	0.94

1991 MONITORING EMISSION DATA

TEST DATE	BLDG #	1990 PRODUCTION SCHEDULE (HRS/YR)	AVG VOC EMISSIONS (LBS/HR)	VOC EMISSIONS (TONS/YR)	NON-PRODUCT. VOC EMISS. 18.3% OF PRODUCT. EMISS. (TONS/YR)	1991 TOTAL EMISSIONS (TONS/YR)
02/91	54	6468	5.70	18.43	3.37	21.81
02/91	57	6936	0.52	1.80	0.33	2.13

2-28-92

Patt,

I've borrowed
your calculator.

BW

MAXIMUM ALLOWABLE VOC/SOLVENT EMISSIONS
UNDER THE EXISTING CONDITIONS

BLDG #	MAX. ALLOWABLE VOC/SOLVENT EMISSIONS (TONS/YR)
54	75.5
55	0.3
57	2.0

=====

NET CHANGE IN MAXIMUM ALLOWABLE VOC/SOLVENT EMISSIONS
UNDER THE PROPOSED CONDITIONS

BLDG #	NET CHANGE VOC/SOLVENT EMISSIONS (TONS/YR)
54	1.7 DECREASE
55	0.7 INCREASE
57	1.0 INCREASE

=====

MAXIMUM ALLOWABLE VOC/SOLVENT EMISSIONS
UNDER THE PROPOSED CONDITIONS

BLDG #	MAX. ALLOWABLE VOC/SOLVENT EMISSIONS (TONS/YR)
54	73.8
55	1.0
57	3.0

ACID MONITORING
BUILDING 54, BUILDING 55, BUILDING 57, BUILDING 59

Acid monitoring work was performed on the Buildings 54, 55, 57 and 59 scrubber systems in June of 1990. Samples were collected using modified EPA method 8 sampling train. The impinger solution used to capture the acids was pure distilled water. The analytical methodology utilized to determine the ions of highest concentration is as follows:

Chloride ion--EPA Method 325.3
Fluoride ion--EPA Method 340.2
Nitrate ion--EPA Method 353.2
Phosphorous--EPA Method 365.2
Sulfate ion--EPA Method 375.2

All test results were in pounds per hour as "X", where "X" represents the acid compound present in highest concentration.

The test results are given on the following table and are expressed as hydrochloric, hydrofluoric, nitric, phosphoric and sulfuric acids. The results are based on the actual production schedule for calendar year 1990. The monitoring was performed over an 8 hour time interval when full production was occurring.

When a resulting acid concentration was expressed as a "less than 'y' " value, where 'y' represents the lowest detectable limit possible using the analytical methodology employed, acid emissions were taken to be equal to this 'y' limit value.

The monitoring indicated a significant drop in acid emissions from Building 54 and a higher than the potential emissions from Building 59. Therefore, we request that the following adjustment be considered:

An increase in the Building 59 acid emissions from 0.1 to 0.3 tons per year.
A decrease in the Building 54 acid emissions from 9.9 to 9.7 tons per year.

The proposed adjustments will not change the overall acid emissions for the site.

SUMMARY OF 1990 ANNUAL MONITORING RESULTS ON ACID EMISSIONS
EXPRESSED AS HCL, HF, HNO3, HPO3 AND H2SO4. THIS DATA IS BASED
ON ACTUAL OPERATING HOURS FOR THE CALLENDAR YEAR 1990.

1990 MONITORING EMISSION DATA

TEST DATE	BLDG #	1990 PRODUCTION SCHEDULE (HRS/YR)	AVG ACID EMISSIONS (LBS/HR)	ACID EMISSIONS (TONS/YR)
06/90	54	6468	1.73	5.59
06/90	59	7242	0.05	0.17

=====

PROJECTED POTENTIAL ACID EMISSIONS
UNDER THE **EXISTING CONDITIONS**

BLDG #	POTENTIAL VOC/SOLVENT EMISSIONS (TONS/YR)
54	9.9
59	0.1

NET CHANGE IN PROJECTED POTENTIAL ACID EMISSIONS
UNDER THE **PROPOSED CONDITIONS**

BLDG #	NET CHANGE VOC/SOLVENT EMISSIONS (TONS/YR)
54	0.2 DECREASE
59	0.2 INCREASE

PROJECTED POTENTIAL ACID EMISSIONS
UNDER THE **PROPOSED CONDITIONS**

BLDG #	POTENTIAL VOC/SOLVENT EMISSIONS (TONS/YR)
54	9.7
59	0.3

ATTACHMENT C.
RAW MATERIALS & CHEMICALS

**BUILDING 54
PROCESS SOLVENTS**

1,1,1 TRIMETHYL-N-TRIMETHYL ETHER
1,1,1 TRICHLOROETHANE
1,2,4 TRICHLOROBENZENE
2-ETHOXYETHYL ACETATE
ACETONE
AROMATIC HYDROCARBON SOLVENT C9-C12
BUTYL CELLOSOLVE
CARBON TETRACHLORIDE
CELLOSOLVE ACETATE
CRESOL
DIPROPYLENE GLYCOL METHYL ETHER
ETHYL BENZENE
FREON 14
FREON 23
FREON TF
HEXAMETHYLDISILIZANE
ISOPARAFFINIC HYDROCARBONS
ISOPROPYL ALCOHOL
METHANOL
N-BUTYL ACETATE
N-METHYL-2-PYRROLIDONE
OIL
OXYLPHENOL POLYETHOXYLATE
PHILTEC SAFETY STAIN
PROPYLENE GLYCOL MONOETHYL ETHER ACETATE
XYLENE

**BUILDING 54
PROCESS CHEMICALS**

ACETIC ACID
ALKYL ARYL SULFONIC ACID
ALUMINA SILICA
AMMONIA
AMMONIUM HYDROXIDE
AMMONIUM FLUORIDE
CERIC SULFATE
CHROMIC ACID
DODECYLBENZENE SULFONIC ACID
ETHYLENE DIAMINE TETRACETIC ACID (EDTA)
ETHYLENE GLYCOL
GLYCERINE
HYDROCHLORIC ACID
HYDROFLUORIC ACID
HYDROGEN PEROXIDE
NITRIC ACID
PHOSPHATE
PHOSPHORIC ACID
POTASSIUM HYDROXIDE
PROPYLENE CARBONATE
SODIUM HYPOPHOSPHITE
SODIUM HYDROXIDE
SULFURIC ACID
TETRAMETHYL AMMONIUM HYDROXIDE

**BUILDING 54
PROCESS GASES**

ARGON
ARSINE
BORON TRIFLUORIDE
BORON TRIBROMIDE
BORON TRICHLORIDE
CARBON DIOXIDE
CHLORINE
DE 100
DIBORANE
DICHLOROSILANE
HELIUM
HYDROGEN
HYDROGEN CHLORIDE
NITROGEN
NITROGEN TRIFLUORIDE
NITROUS OXIDE
OXYGEN
PDE 100
PHOSPHINE
PHOSPHOROUS OXYCHLORIDE
PHOSPHOROUS TRIBROMIDE
SILANE
SULFUR HEXAFLUORIDE
TUNGSTEN HEXAFLUORIDE

HARRIS SEMICONDUCTOR
BUILDING 55
LIST OF SOLVENTS

1,1,1-TRICHLOROETHANE
1,2,4-TRICHLOROBENZENE
1,2-DICHLOROBENZENE
ACETONE
CELLOSOLVE ACETATE
CRESOL
ETHANOL
ETHYLBENZENE
ETHYLENE GLYCOL
FREON 113
ISOPROPANOL
METHANOL
N-BUTYL ACETATE
N-METHYL PYRROLIDONE
PROPYLENE GLYCOL MONOMETHYL ETHER ACETATE
TETRAMETHYL AMMONIUM HYDROXIDE
TOLUENE
XYLENE
HEXAMETHYLDISILAZANE

BUILDING 55
PROCESS CHEMICALS

ACETIC ACID
AMMONIUM FLUORIDE
AMMONIUM HYDROXIDE
BORON TRIBROMIDE
HYDROCHLORIC ACID
HYDROFLUORIC ACID
NITRIC ACID
NITROGEN
OXYGEN
PHOSPHORIC ACID
PHOSPHOROUS OXYCHLORIDE
SULFURIC ACID
WASTE ACIDS
WASTE SOLVENTS
WASTE SULFURIC ACID

BUILDING 57
PROCESS SOLVENTS

1,1,1 TRICHLOROETHANE
4-METHYL-2,4-PENAHNEDIOL
ACETONE
ALIPHATIC ESTER
ALIPHATIC SOLVENTS
ALKANOLAMINE
ALKYL AMINE
CARBON TETRACHLORIDE
CELLOSOLVE ACETATE
CHLOROFORM
ETHANOL
ETHYL ACETATE
ETHYLENE GLYCOL MONOBUTYL ETHER ACETATE
ETHYLENE GLYCOL MONOETHYL ACETATE
FLUORINERT FC-71
FLUORINERT FC-84
HEXANE
HYDROQUINONE
ISOPROPANOL
METHANOL
METHYLENE CHLORIDE
N-METHYL-2-PYRROLIDONE
ORGANIC SALT
PETROLATUM
PROPYLENE GLYCOL MONOMETHYL ETHER ACETATE
TRICHLOROETHYLENE
TRICHLOROTRIFLUOROETHANE
TRIETHYLENE GLYCOL MONOMETHYL ETHER
TURPENTINE
XYLENE

BUILDING 57
PROCESS CHEMICALS

ACTIVATORS
AMINE SALT
AMINO ACID CHLORIDE
AMMONIUM BIFLUORIDE
AMMONIUM CHLORIDE
AMMONIUM HYDROXIDE
AMMONIUM PHOSPHATE
ANTIMONY
ANTIOXIDANT
BENZOIC ACID
BISMUTH
BORIC ACID
CADMIUM MERCURY SULFIDE
CADMIUM SULFOSELENIDE RED
CARAMIDE
CARBOXYLIC ACID-PHENOL
CITRIC ACID
CRESOL
DIMETHYL PHTHALATE
ETHOXYLATED TALL OIL FATTY ACIDS
FATTY ACID GLYCERIDES
FATTY ACIDS
FLUOBORIC ACID
FLUORIDE SALT
FORMIC ACID
GLUTAMATE POLYMER ACTIVATOR
GLUTAMATE POLYMER HYDROCHLORIDE
GLYCERINE
GLYCEROL
GUM RESIN
HYDROCHLORIC ACID
HYDROCHLORIDE
HYDROFLUORIC ACID
HYDROGEN PEROXIDE
INDICATING DYE
INDIUM
INORGANIC CARBONATES
INORGANIC OXIDES
ISOBUTANE PROPELLANT
ISOPHORONE
JANUS GREEN B
LEAD
LEAD CHROMATE
LEAD SALT
LITHIUM SALT
METHYL CHLORIDE
MONOETHANOLAMINE
NITRIC ACID
ORGANIC ACID

(CONTINUED)

BUILDING 57
PROCESS CHEMICALS

ORGANIC ACID PHOSPHATE
PETROLEUM OIL
PHOSPHORIC ACID
POLYFUNCTIONAL ACID
POTASSIUM 2-CHLORO-4-NITROBENZOATE
POTASSIUM BIFLUORIDE
POTASSIUM CYANIDE
POTASSIUM CYANOaurITE
POTASSIUM PENTABORATE
POTASSIUM TETRABORATE
RESIN
ROSIN
SILVER
SODIUM BICARBONATE
SODIUM CARBONATE
SODIUM DODECYL SULFATE
STANNOUS SULFATE
STEARIC ACID
SULFATE
SULFURIC ACID
SURFACTANTS
THIOUREA
TIN
WATER SOLUBLE DISPERANT
ZINC CHLORIDE

BUILDING 59
PROCESS SOLVENTS

1,1,1 TRICHLOROETHANE
2-ETHOXYETHYL ACETATE
ACETONE
BUTYL CELLOSOLVE
CARBON TETRACHLORIDE
CELLOSOLVE ACETATE
CHLOROPENTAFLUOROETHANE
DICHLORODIFLUOROETHANE
ETHYLENE DIAMINE TETRACETIC ACID (ED
ETHYL ALCOHOL
ETHYL BENZENE
ETHYLENE DIAMINE
ETHYLENE GLYCOL MONOMETHYL ETHER
FLUOROCARBON-72
FREON 5311
FREON TF
FREON TMS
ISOPROPYL ALCOHOL
ISOPARAFFINIC HYDROCARBONS
METHANOL
METHYL ETHYL KETONE
METHYLPHENYL ETHER
METHYL-2-PYRROLIDINONE
MONOETHANOLAMINE
N,N-DIMETHYLFORMAMIDE
N-BUTYL ACETATE
N-BUTYL ALCOHOL
N-METHYL PYRROLIDONE
PROPYLENE GLYCOL
PROPYLENE GLYCOL 1,2 PROPANEDIOL
TOLUENE
TRICHLOROTRIFLUOROETHANE
XYLENE

BUILDING 59
PROCESS CHEMICALS

AMYL ACETATE
AMMONIA
AMMONIUM FLUORIDE
AMMONIUM HYDROXIDE
BORON NITRIDE
ETHYLENE GLYCOL
GLYCERINE
HYDROCHLORIC ACID
HYDROFLUORIC ACID
HYDROGEN PEROXIDE
MOLYBDENUM DISULFIDE
NITRIC ACID
PHOSPHORIC ACID
POTASSIUM DICHROMATE
POTASSIUM PHOSPHATE
RED PHOSPHOROUS
SODIUM CARBONATE
SODIUM HYDROXIDE
SODIUM PHOSPHATE
SULFURIC ACID
TETRAETHYL ORTHOSILICATE (TEOS)
TETRAMETHYL AMMONIUM HYDROXIDE
TRISODIUM PHOSPHITE

BUILDING 59
PROCESS GASSES

ARGON
BORON TRIBROMIDE
BORON TRIFLUORIDE
CHLORINE
DICHLOROSILANE
HELIUM
HEXAFLUOROETHANE
HYDROGEN
HYDROGEN CHLORIDE
NITROGEN
NITROGEN TRIFLUORIDE
NITROUS OXIDE
OXYGEN
OZONE
PHOSPHINE
PHOSPHOROUS OXYCHLORIDE
SILANE
SULFUR HEXAFLUORIDE
TRIMETHYL BORATE
TRIMETHYL PHOSPHATE
TUNGSTEN HEXAFLUORIDE

ATTACHMENT D.
CONTROL EQUIPMENT

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 54 DATE ISSUED : 10/25/88
PERMIT NUMBER: AC 05-147321 RENEWAL DATE: 08/29/90
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 06/30/91

AREA SERVED: BUILDING 54 WEST SIDE
PROCESS DESCRIPTION: ACID AND VOC/SOLVENT SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 50,000
ACID MIST(TON/YR): 9.9
SOLV/VOCS(TON/YR): 75.5

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/31
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-50HT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS REINFORCED
HARRIS ID NUMBER: F54S01 PLASTIC
LOCATION : B54 GROUND NORTHWEST CORNER

DESCRIPTION : HORIZONTAL CROSS FLOW, NON-CLOGGING PVC SPRAY NOZZLES,
2" POLYPROPYLENE PACKING, PVC MIST ELIMINATOR

DESIGN DATA

VOLUME FLOW RATE (CFM): 50,000 STACK HEIGHT (FT): 65
RECIRCULATION RATE (GPM): 225 STACK DIAMETER (IN): 54/48
MAKE UP WATER RATE (GPM): 22 STACK VELOCITY (FPM): 3200
PRESSURE DROP (IN): 2.5

ACTUAL DATA

VOLUME FLOW RATE (CFM): 43,141 PRESSURE DROP (IN): 0.7
RECIRCULATION RATE (GPM): 70 MAKE UP WATER RATE (GPM): 4
DATE: 9/10/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP IND MODEL NUMBER : P-7.5
SERIAL NUMBER: 106001/106002 HP : 7.5 RPM : 3500/2900
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : MCC-P

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-60
SERIAL NUMBER: F-600 MATERIAL : FIBERG.REINFORCED PLASTIC
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD INCLINED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 50,000
SPEED (RPM): 629

STATIC PRESS (IN): 5.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 43,141
SPEED (RPM) :

STATIC PRESS (IN): 1.8
DATE : 11/6/90

FAN MOTOR INFORMATION

MANUFACTURER :
SERIAL NUMBER:

MODEL NUMBER:
HP: 75 SPEED (RPM):

BRKR LOCATION: NEXT TO UNIT

FED FROM MCC: 634

PERMIT HISTORY

PERMIT NUMBER: AO 05-65408
DATE EXPIRED : 05/02/88

PERMIT NUMBER: AC 05-147321
DATE EXPIRED : 06/30/91 (SUPERCEDED)

PERMIT NUMBER:
DATE EXPIRED :

PERMIT NUMBER:
DATE EXPIRED :

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 54 DATE ISSUED : 02/28/91
PERMIT NUMBER: AC 05-190800 RENEWAL DATE:
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 12/31/91

AREA SERVED: BUILDING 54 EAST SIDE
PROCESS DESCRIPTION: ACID AND VOC/SOLVENT SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 17,000
ACID MIST(TON/YR): 9.9
SOLV/VOCS(TON/YR): 75.5

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/31
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : HARRINGTON MODEL NUMBER : ECH 66-9PBS
SERIAL NUMBER: S11164-4 MATERIAL : FIBERGLASS REINFORCED
HARRIS ID NUMBER: F54S02 PLASTIC
LOCATION : B54 GROUND NORTHEAST CORNER, NORTHERNLY POSITION

DESCRIPTION : HORIZONTAL CROSS-FLOW, GLASDEX 12060 PVC PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, PVC MIST ELIMINATOR

DESIGN DATA

VOLUME FLOW RATE (CFM): 17,000 STACK HEIGHT (FT): 65
RECIRCULATION RATE (GPM): 144 STACK DIAMETER (IN): 60/48
MAKE UP WATER RATE (GPM): 10 STACK VELOCITY (FPM): 3400
PRESSURE DROP (IN): 2.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 16,000 PRESSURE DROP (IN): 0.7
RECIRCULATION RATE (GPM): 120 MAKE UP WATER RATE (GPM): 6
DATE: 9/10/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP IND MODEL NUMBER : P-6A
SERIAL NUMBER: P89830/P89831 HP : 7.5 RPM : 3500\2900
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : MCCT-D4

FAN INFORMATION

HARRIS ID # : F54E13
MANUFACTURER : HEIL MODEL NUMBER: 42HBI
SERIAL NUMBER: F-108 MATERIAL : FIBERG.REINFORCED PLASTIC
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD INCLINED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 17,000
SPEED (RPM): 790

STATIC PRESS (IN): 5.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 16,000
SPEED (RPM) :

STATIC PRESS (IN): 3.0
DATE : 6/22/91

FAN MOTOR INFORMATION

MANUFACTURER : BALDOR IND MOTOR
SERIAL NUMBER: 10/78

MODEL NUMBER: M41151
HP: 50 SPEED (RPM): 1760

BRKR LOCATION: NEXT TO UNIT

FED FROM MCC: MCCT-D4

PERMIT HISTORY

PERMIT NUMBER: AO 05-38488
DATE EXPIRED : 04/08/86

PERMIT NUMBER: AO 05-115804
DATE EXPIRED : 05/22/91 (SUPERCEDED)

PERMIT NUMBER: AC 05-147321
DATE EXPIRED : 06/30/91 (SUPERCEDED)

PERMIT NUMBER:
DATE EXPIRED :

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 54 DATE ISSUED : 02/28/91
PERMIT NUMBER: AC 05-190800 RENEWAL DATE:
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 12/31/91

AREA SERVED: BUILDING 54 EAST SIDE
PROCESS DESCRIPTION: ACID AND VOC/SOLVENT SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 30,000
ACID MIST(TON/YR): 9.9
SOLV/VOCS(TON/YR): 75.5

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/31
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-24HT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS REINFORCED
HARRIS ID NUMBER: F54S03 PLASTIC
LOCATION : B54 GROUND NORTHEAST CORNER, SOUTHERLY POSITION

DESCRIPTION : HORIZONTAL CROSS FLOW, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR

DESIGN DATA

VOLUME FLOW RATE (CFM): 30,000 STACK HEIGHT (FT): 65
RECIRCULATION RATE (GPM): 175 STACK DIAMETER (IN): 60/48
MAKE UP WATER RATE (GPM): 12 STACK VELOCITY (FPM): 3400
PRESSURE DROP (IN): 2

ACTUAL DATA

VOLUME FLOW RATE (CFM): 29,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 165 MAKE UP WATER RATE (GPM): 5
DATE: 9/10/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP IND MODEL NUMBER : P-7.5
SERIAL NUMBER: 89828/89829 HP : 7.5 RPM : 3500/2900
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : MCCS-B5
MCCS-A1

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : VIRON MODEL NUMBER: VCF-144
SERIAL NUMBER: 10619 MATERIAL : FIBERG.REINFORCED PLASTIC
DESCRIPTION : CENTIFUGAL TYPE, CLASS II, BACKWARD INCLINED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 30,000
SPEED (RPM): 1760

STATIC PRESS (IN): 5.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 29,000
SPEED (RPM) :

STATIC PRESS (IN): 3.0
DATE : 5/22/91

FAN MOTOR INFORMATION

MANUFACTURER : BALDOR IND. MOTOR
SERIAL NUMBER: M4110T

MODEL NUMBER:
HP: 40 SPEED (RPM): 1760

BRKR LOCATION: NEXT TO UNIT

FED FROM MCC:

PERMIT HISTORY

PERMIT NUMBER: AO 05-38488
DATE EXPIRED : 04/09/81

PERMIT NUMBER: AO 05-115804
DATE EXPIRED : 5/22/91 (SUPERCEDED)

PERMIT NUMBER: AC 05-147321
DATE EXPIRED : 06/30/91 (SUPERCEDED)

PERMIT NUMBER:
DATE EXPIRED :

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 55 DATE ISSUED : 02/28/91
PERMIT NUMBER: AC 05-190799 RENEWAL DATE:
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 12/31/91

AREA SERVED: BUILDING 55
PROCESS DESCRIPTION: ACID AND VOC/SOLVENT SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 9,500
ACID MIST(TON/YR): 0.1
SOLV/VOCS(TON/YR): 0.3

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 3/31
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : TRI-MER CORP.
SERIAL NUMBER: 7026
HARRIS ID NUMBER: F55S01
LOCATION : B55 ROOF

MODEL NUMBER : F/W 3
MATERIAL : PVC

DESCRIPTION : HORIZONTAL COUNTER-FLOW, MIST ELIMINATOR,
POLYPROPELENE FILTER PACK

DESIGN DATA

VOLUME FLOW RATE (CFM): 9,500 STACK HEIGHT (FT): 12
RECIRCULATION RATE (GPM): 30 STACK DIAMETER (IN): 14
MAKE UP WATER RATE (GPM): 3.0 STACK VELOCITY (FPM):
PRESSURE DROP (IN): 1.5

ACTUAL DATA

VOLUME FLOW RATE (CFM): 7,500 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 10 MAKE UP WATER RATE (GPM): 8
DATE: 9/29/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FLOTEK
SERIAL NUMBER: 603887B801
BRKR LOCATION: NEXT TO UNIT

MODEL NUMBER : C7P3-1194V
HP : 2 RPM : 3450/2850
FED FROM MCC : CKT 25,27,29

FAN INFORMATION

HARRIS ID # : F55E13
MANUFACTURER : TRI-MER CORP.
SERIAL NUMBER: 7026
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD INCLINED BLADES

MODEL NUMBER: 24 UB
MATERIAL : PVC

DESIGN DATA

VOLUME FLOW RATE (CFM): 7500
SPEED (RPM): 1789

STATIC PRESS (IN): 5

ACTUAL DATA

VOLUME FLOW RATE (CFM): 7500
SPEED (RPM) :

STATIC PRESS (IN): 3
DATE : 9/10/91

FAN MOTOR INFORMATION

MANUFACTURER : LINCOLN
SERIAL NUMBER: 2314895

MODEL NUMBER: 254T
HP: 15 SPEED (RPM): 1750

BRKR LOCATION: NEXT OT UNIT

FED FROM MCC: CKT 7,9,11

PERMIT HISTORY

PERMIT NUMBER: AC 05-104523
DATE EXPIRED : 06/30/86

PERMIT NUMBER: AC 05-164544
DATE EXPIRED : 06/30/91 (SUPERCEDED)

PERMIT NUMBER:
DATE EXPIRED :

PERMIT NUMBER:
DATE EXPIRED :

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 57 DATE ISSUED : 01/11/91
PERMIT NUMBER: AC 05-189178 RENEWAL DATE:
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 12/31/91

AREA SERVED: Building 57
PROCESS DESCRIPTION: ACID AND VOC/SOLVENT SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 13,500
ACID MIST(TON/YR): 0.2
SOLV/VOCS(TON/YR): 2.0

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/31
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : TRI-MER CORP. MODEL NUMBER : F/W 5
SERIAL NUMBER: 7029 MATERIAL : PVC
HARRIS ID NUMBER: F57S01
LOCATION : B57 ROOF CENTER OF BLDG

DESCRIPTION : HORIZONTAL COUNTER-FLOW, MIST ELIMINATOR,
POLYPRO FILTER PACK

DESIGN DATA

VOLUME FLOW RATE (CFM): 13,500 STACK HEIGHT (FT): 12
RECIRCULATION RATE (GPM): 36 STACK DIAMETER (IN): 32
MAKE UP WATER RATE (GPM): 2.0 STACK VELOCITY (FPM): 2417
PRESSURE DROP (IN):

ACTUAL DATA

VOLUME FLOW RATE (CFM): 9,328 PRESSURE DROP (IN): 2.8
RECIRCULATION RATE (GPM): 38 MAKE UP WATER RATE (GPM): 4.0
DATE: 09/19/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FLOTEC MODEL NUMBER : C8P8-1194V
SERIAL NUMBER: HP : 1.5 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : PP 26

FAN INFORMATION

HARRIS ID # : F57E03
MANUFACTURER : TRI-MER CORP. MODEL NUMBER: 30 FAN UB
SERIAL NUMBER: 5397 MATERIAL : PVC
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD INCLINED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 13,500
SPEED (RPM): 1750

STATIC PRESS (IN): 1.7

ACTUAL DATA

VOLUME FLOW RATE (CFM): 9,328
SPEED (RPM) :

STATIC PRESS (IN): 1.1
DATE : 11/06/90

FAN MOTOR INFORMATION

MANUFACTURER :
SERIAL NUMBER: R-8361-04-296

MODEL NUMBER: 256T
HP: 20 SPEED (RPM): 1750

BRKR LOCATION: NEXT TO UNIT

FED FROM MCC: PP 26

PERMIT HISTORY

PERMIT NUMBER: AC 05-104522
DATE EXPIRED : 06/30/86

PERMIT NUMBER: AC 05-161706
DATE EXPIRED : 06/30/91

PERMIT NUMBER:
DATE EXPIRED :

PERMIT NUMBER:
DATE EXPIRED :

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 59 DATE ISSUED : 08/15/90
PERMIT NUMBER: AC 05-180707 RENEWAL DATE: 06/04/91
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 12/31/91

AREA SERVED: WAFER FAB AND RELIABILITY, BUILDING 59
PROCESS DESCRIPTION: ACID VAPOR SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 40,000
ACID MIST(TON/YR): 0.1
SOLV/VOCS(TON/YR): 8.4

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/01
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-40HT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
HARRIS ID NUMBER: F59S01
LOCATION : B59 GROUND WEST SIDE

DESCRIPTION : HORIZONTAL CROSS FLOW, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR, DWG. F-600-1

DESIGN DATA

VOLUME FLOW RATE (CFM): 40,000 STACK HEIGHT (FT): 35
RECIRCULATION RATE (GPM): 175 STACK DIAMETER (IN): 44
MAKE UP WATER RATE (GPM): 17.5 STACK VELOCITY (FPM):
PRESSURE DROP (IN):

ACTUAL DATA

VOLUME FLOW RATE (CFM): 30,838 PRESSURE DROP (IN): 1.5
RECIRCULATION RATE (GPM): 120 MAKE UP WATER RATE (GPM): 5.0
DATE: 09/19/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP INC MODEL NUMBER : 36E188-105
SERIAL NUMBER: F1280 HP : 3 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5912

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-49
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD CURVED BLADES,
DWG. F-600-1

DESIGN DATA

VOLUME FLOW RATE (CFM): 33,384
SPEED (RPM): 764

STATIC PRESS (IN): 5.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 30,838
SPEED (RPM) :

STATIC PRESS (IN): 2.8
DATE : 11/06/90

FAN MOTOR INFORMATION

MANUFACTURER : LINCOLN
SERIAL NUMBER:

MODEL NUMBER: 324T
HP: SPEED (RPM): 1750

BRKR LOCATION: NEXT TO UNIT

FED FROM MCC: 5912, 5913

PERMIT HISTORY

PERMIT NUMBER: AC 05-54991
DATE EXPIRED : 06/01/84

PERMIT NUMBER: AC 05-104516
DATE EXPIRED : 06/30/86

PERMIT NUMBER: AO 05-121924
DATE EXPIRED : 09/14/91

PERMIT NUMBER:
DATE EXPIRED :

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 59 DATE ISSUED : 08/15/90
PERMIT NUMBER: AC 05-180707 RENEWAL DATE: 06/04/91
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 12/31/91

AREA SERVED: WAFER FAB AND RELIABILITY LAB, BUILDING 59
PROCESS DESCRIPTION: VOC/SOLVENT SCRUBBER

BLDG PERMIT INFORMATION

VOL. RATE (SCFM): 20,000
ACID MIST(TON/YR): 0.0228
SOLV/VOCS(TON/YR): 1.91

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/31
NOTIFICATION OF VE TEST : N/A
ANNUAL VIS EMISSION TEST: N/A

OPER. (HRS/YEAR): 8760

SCRUBBER INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-24VT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
HARRIS ID NUMBER: F59S02
LOCATION : B59 GROUND WEST SIDE

DESCRIPTION : VERTICAL COUNTER-CURRENT, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR, DWG. F-600-2

DESIGN DATA

VOLUME FLOW RATE (CFM): 24,000 STACK HEIGHT (FT): 35
RECIRCULATION RATE (GPM): 105 STACK DIAMETER (IN): 42
MAKE UP WATER RATE (GPM): 10.5 STACK VELOCITY (FPM):
PRESSURE DROP (IN):

ACTUAL DATA

VOLUME FLOW RATE (CFM): 10,972 PRESSURE DROP (IN): 0.5
RECIRCULATION RATE (GPM): 64 MAKE UP WATER RATE (GPM): 5.0
DATE: 9/19/91

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP IND MODEL NUMBER : 36E188-105
SERIAL NUMBER: F1280 HP : 3 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5912

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-36
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD CURVED BLADES,
DWG. F-600-2

DESIGN DATA

VOLUME FLOW RATE (CFM): 16,000
SPEED (RPM): 1087

STATIC PRESS (IN): 6.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 10,972
SPEED (RPM) : 1065

STATIC PRESS (IN): 5.6
DATE : 11/06/90

FAN MOTOR INFORMATION

MANUFACTURER : LINCOLN
SERIAL NUMBER:

MODEL NUMBER: 284T
HP: SPEED (RPM): 1750

BRKR LOCATION: NEXT TO UNIT

FED FROM MCC: 5912 & 5913

PERMIT HISTORY


PERMIT NUMBER: AC 05-54990
DATE EXPIRED : 06/01/84

PERMIT NUMBER: AC 05-104515
DATE EXPIRED : 06/30/86

PERMIT NUMBER: AO 05-121924
DATE EXPIRED : 09/14/91

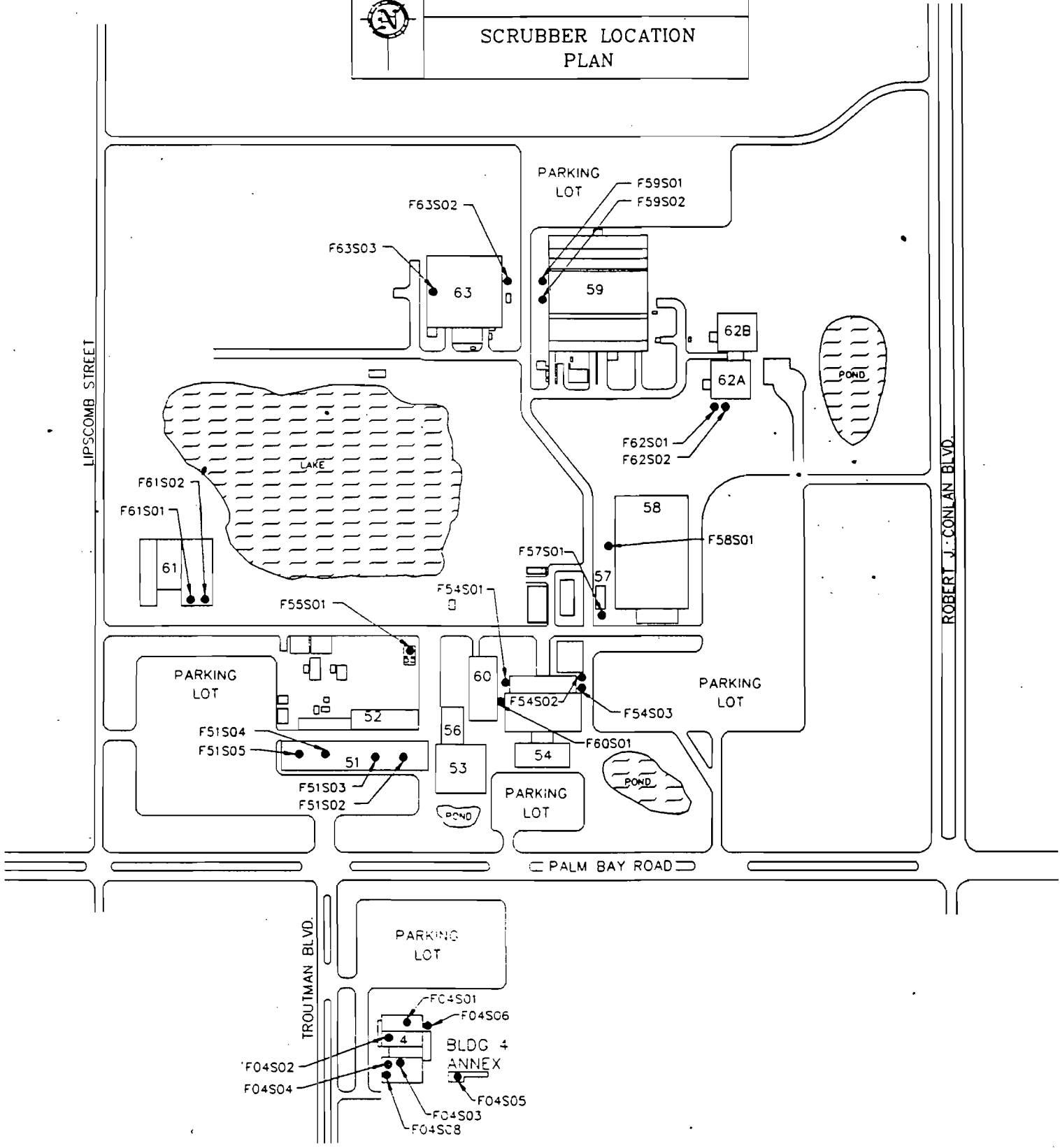
PERMIT NUMBER:
DATE EXPIRED :

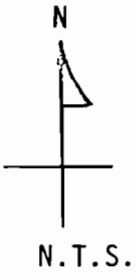
ATTACHMENT E.
LOCATION MAPS



HARRIS
SEMICONDUCTOR
A DIVISION OF HARRIS CORPORATION

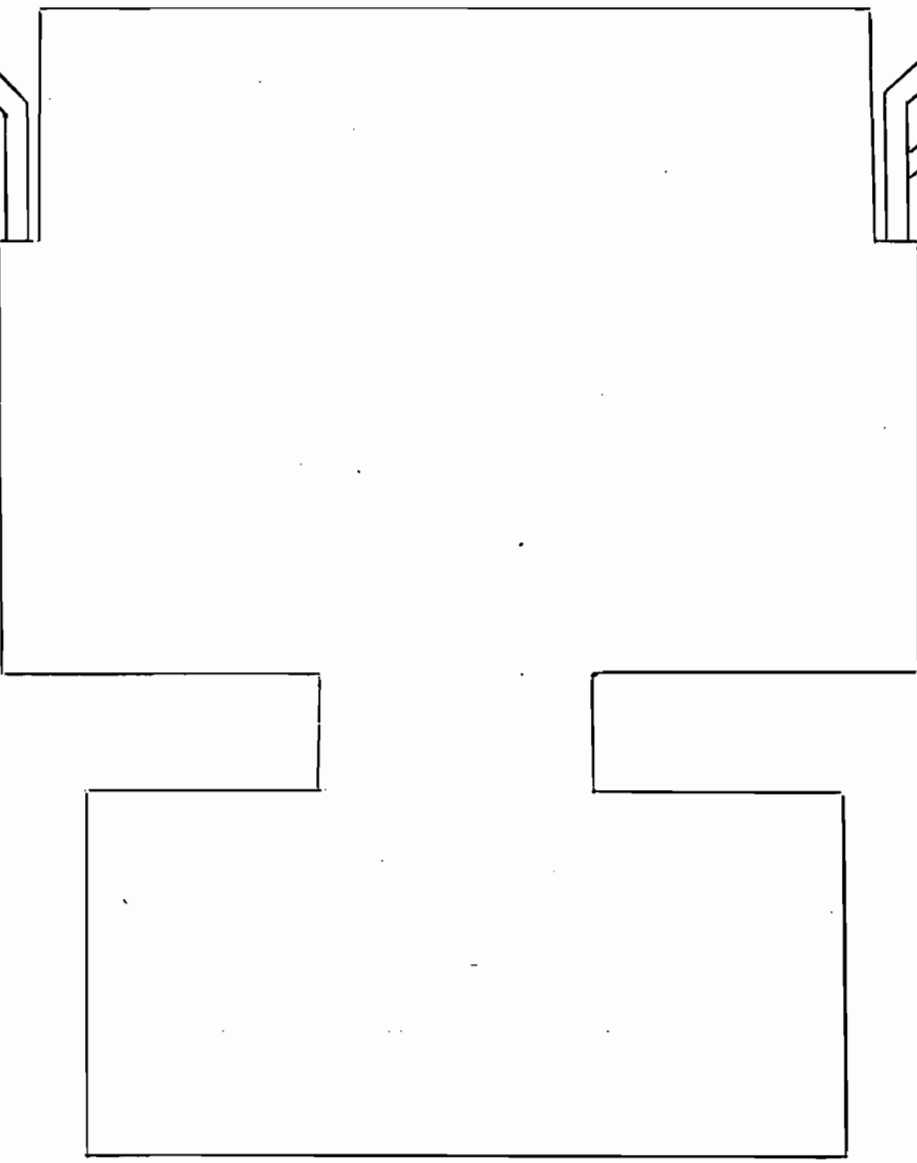
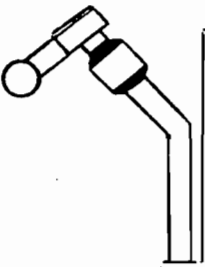
SCRUBBER LOCATION
PLAN



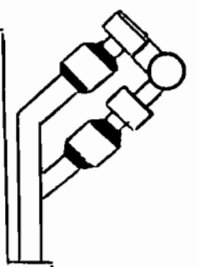


HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 54

F54S01









F54S02

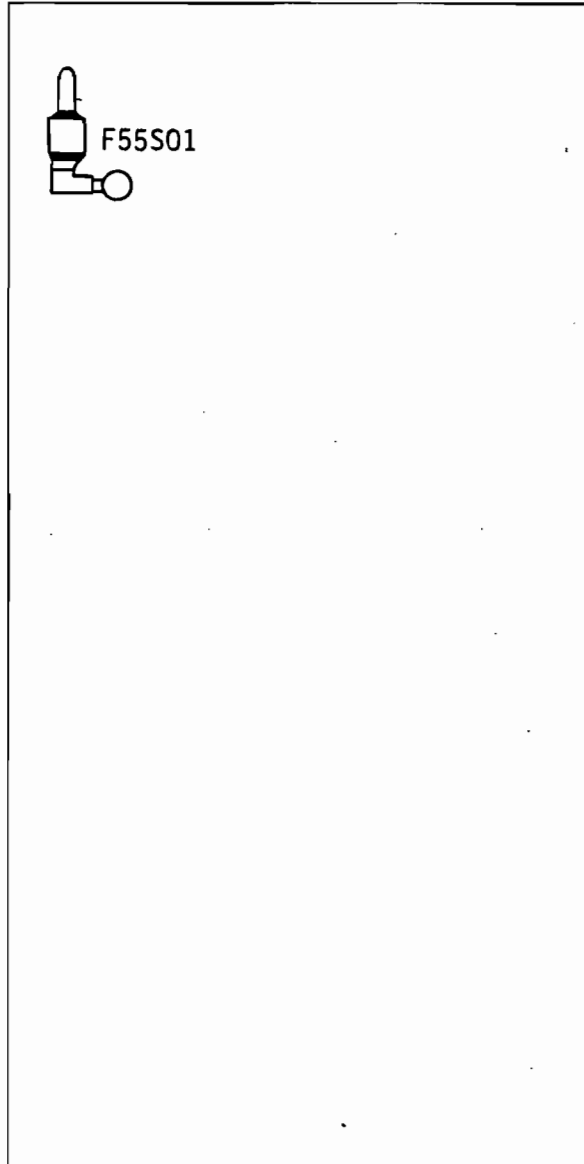
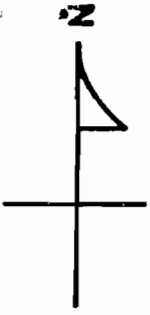


F54S03





LEGEND

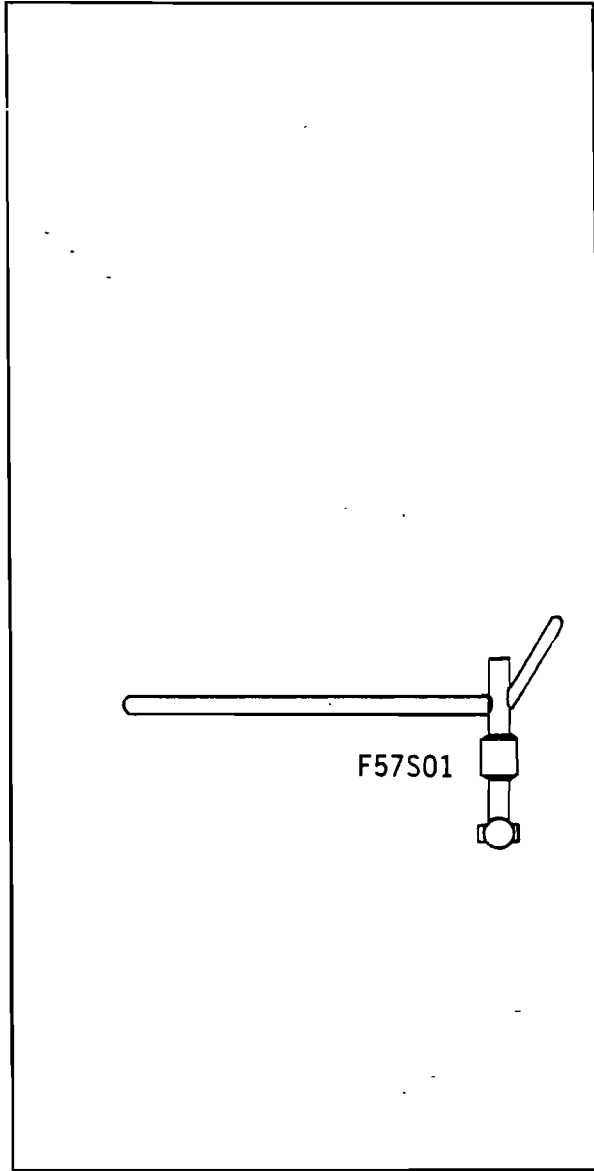
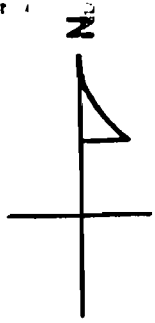
-  - Horizontal Scrubber
-  - Vertical Scrubber
-  - Exhaust Stack
-  - Exhaust Fan
-  - Stack mounted on Fan
-  - Epitaxial Scrubber

HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 55









LEGEND

-  - Horizontal Scrubber
-  - Vertical Scrubber
-  - Exhaust Stack
-  - Exhaust Fan



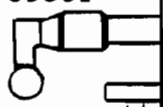
LEGEND

- | | |
|---|------------------------|
|  | - Horizontal Scrubber |
|  | - Vertical Scrubber |
|  | - Exhaust Stack |
|  | - Exhaust Fan |
|  | - Stack mounted on fan |
|  | - Epitaxial Scrubber |

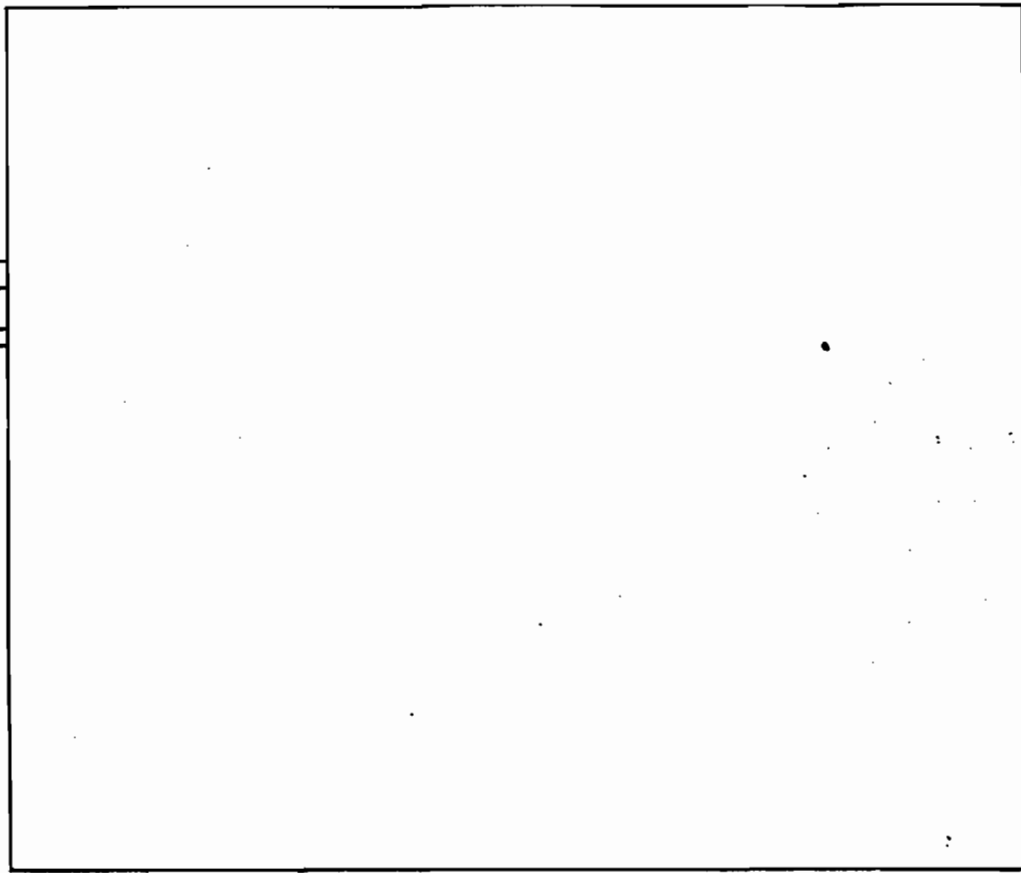
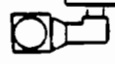
HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 59









F59S01



F59S02



LEGEND

	- Horizontal Scrubber
	- Vertical Scrubber
	- Exhaust Stack
	- Exhaust Fan
	- Stack mounted on fan
	- Epitaxial Scrubber

DEPARTMENT OF ENVIRONMENTAL REGULATION

ROUTING AND TRANSMITTAL SLIP	ACTION NO
	ACTION DUE DATE

1. TO: (NAME, OFFICE, LOCATION)	Initial
<i>Bruce Mitchell, Eng IV</i>	Date
2. <i>PGM-BAQM-</i>	Initial
	Date
3. <i>CAPS - Room 310 D</i>	Initial
	Date
4. <i>Jall - Twin Towers</i>	Initial
	Date

REMARKS:

RECEIVED

MAR 21 1988

DER-BAQM

INFORMATION

- Review & Return
- Review & File
- Initial & Forward

DISPOSITION

- Review & Respond
- Prepare Response
- For My Signature
- For Your Signature
- Let's Discuss
- Set Up Meeting
- Investigate & Report
- Initial & Forward
- Distribute
- Concurrence
- For Processing
- Initial & Return

FROM:

John Turner

DATE

3/18/88

PHONE

INTEROFFICE MEMORANDUM

For Routing To District Offices And/Or To Other Than The Addressee		
To: _____	Loctn.: _____	
To: _____	Loctn.: _____	
To: _____	Loctn.: _____	
From: _____	Date: _____	
Reply Optional []	Reply Required []	Info. Only []
Date Due: _____	Date Due: _____	

TO: BRUCE MITCHELL

THROUGH: A. ALEXANDER *AA*
C.M. COLLINS *cm c*
A.T. SAWICKI *AS*

FROM: JOHN TURNER *JT*

DATE: MARCH 17, 1988

SUBJECT: HARRIS SEMICONDUCTOR - BUILDING 54 PERMIT CONSOLIDATION.

We have reviewed a copy of the referenced application sent to BAQM, Central Air Permitting Staff from Harris Semiconductor that requests consolidating permits A005-65408 and A005-115804 at building 54. We have the following comments:

- a. Permit A005-65408 is in need of renewal as it expires 5/2/88.
- b. The most recent permit renewals for these permits appear to indicate total VOC emission rates of approximately 4.7 tons/year (copies enclosed), which is significantly less than the requested VOC emission rate of 94.34 tons/year of attachment B.
- c. The application dated March 2, 1988, attachment B, indicates a 13% VOC reduction due to scrubber efficiency but does not address whether these VOC's are emitted elsewhere downstream of the scrubbers. We believe most of these VOC's are emitted from the aeration pond used to neutralize industrial wastewater.
- d. The application does not address the VOC capture efficiency and VOC emission rate of the uncaptured VOC's.
- e. When the VOC material balance is received, it may show VOC emissions are significantly different than the tested and projected emissions of attachment B.

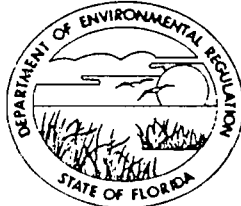
Enclosure

Copied: Bruce Mitchell }
CHF/BT } 3-21-88 my

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

ST. JOHNS RIVER
DISTRICT

3319 MAGUIRE BOULEVARD
SUITE 232
ORLANDO, FLORIDA 32803



BOB GRAHAM
GOVERNOR

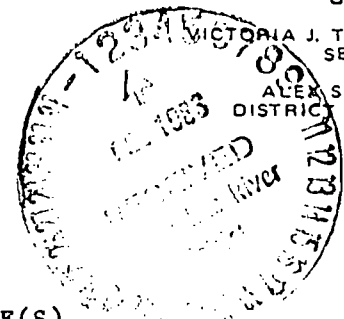
VICTORIA J. TSCHINKEL
SECRETARY
ALEX SENKEVICH
DISTRICT MANAGER

PAID
100

FEB 02 1983

SAINT JOHNS
RIVER DISTRICT

APPLICATION FOR RENEWAL OF
PERMIT TO OPERATE AIR POLLUTION SOURCE(S)



If major alterations have occurred, the applicant should complete the Standard Air Permit Application Form.

Source Type: Fume Hood Exhaust Scrubber Renewal of DER Permit No. A005-6882

Company Name: Harris Semiconductor County: Brevard

Identify the specific emission point source(s) addressed in this application (i.e., Lime Kiln No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired):

Building 54 - W - System 1

Source Location: Street: Palm Bay Road City: Palm Bay

UTM: East 17-538700 North 17-31000900

Latitude: 2 8° 0 1' 2 0"N. Longitude: 8 0° 3 6' 1 0"W.

1. Attach a check made payable to the Department of Environmental Regulation in accordance with operation permit fee schedule set forth in Florida Administrative Code Rule 17-4.05.
2. Have there been any alterations to the plant since last permitted? [] Yes [X] No
If minor alterations have occurred, describe on a separate sheet and attach.
3. Attach the last compliance test report required per permit conditions if not submitted previously.
4. Have previous permit conditions been adhered to? [X] Yes [] No If no, explain on a separate sheet and attach.
5. Has there been any malfunction of the pollution control equipment during tenure of current permit? [] Yes [X] No If yes, and not previously reported, give brief details and what action was taken on a separate sheet and attach.
6. Has the pollution control equipment been maintained to preserve the collection efficiency last permitted by the Department? [X] Yes [] No
7. Has the annual operating report for the last calendar year been submitted? [X] Yes [] No If no, please attach.

8. Please provide the following information if applicable:

A. Raw Materials and Chemical Used in Your Process:

Description	Contaminant		Utilization	
	Type	%Wt	Rate	lbs/hr
Silicon Wafers				
See Attachment A			See Attachment A	

B. Product Weight (lbs/hr): _____

C. Fuels N/A

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	Avg/hr*	Max/hr**	


D. Normal Equipment Operating Time: hrs/day 24 ; days/wk 5 ; wks/yr 52 ;
 hrs/yr (power plants only) _____ ; if seasonal, describe _____

The undersigned owner or authorized representative*** of Harris Semiconductor is fully aware that the statements made in this application for a renewal of a permit to operate an air pollution source are true, correct and complete to the best of his knowledge and belief. Further, the undersigned agrees to maintain and operate the pollution source and pollution control facilities in such a manner as to comply with the provisions of Chapter 403, Florida Statutes, and all the rules and regulations of the Department. He also understands that a permit, if granted by the Department, will be non-transferable and he will promptly notify the Department upon sale or legal transfer of the permitted facility.

*During actual time of operation.

**Units: Natural Gas-MMCF/hr;
 Fuel Oils-barrels/hr; Coal-lbs/hr.

***Attach letter of authorization if not previously submitted


 Signature, Owner or Authorized Representative
 (Notarization is mandatory)

A. King, Vice President (for P. R. Bumgarner)
 Typed Name and Title

P. O. Box 883
 Address

Melbourne FL 32901
 City State Zip

1/31/83 Date Telephone No. (305) 724-7225

ATTACHMENT A

HARRIS SEMICONDUCTOR

Exhaust System, Building 54

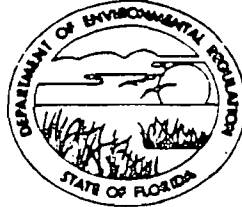
RAW MATERIAL	UTILIZATION RATE LB/HR.	DISCHARGE POUND/HOUR	DISCHARGE TON/YEAR
Hydrofluoric Acid	3.0	0.045	0.140
Sulphuric Acid	19.0	0.286	0.892
Hydrogen Peroxide	1.7	0.026	0.081
Hydrochloric Acid	0.8	0.012	0.004
Nitric Acid	0.5	0.007	0.022
Trichloro-ethylene	2.1	0.0415	0.1294
Xylene	2.8	0.0554	0.1730
Isopropyl Alcohol	0.5	0.0106	0.0329
Methyl Alcohol	2.2	0.0436	0.1359

Handwritten: 1.6102 TPA

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

ST. JOHNS RIVER
DISTRICT

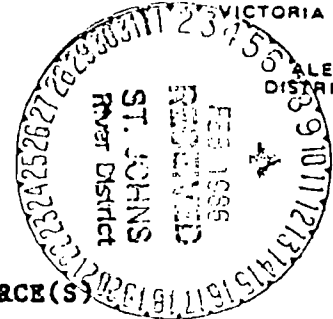
3319 MAGUIRE BOULEVARD
SUITE 232
ORLANDO, FLORIDA 32803



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKL
SECRETARY

ALEX SENKEVICH
DISTRICT MANAGER



APPLICATION FOR RENEWAL OF
PERMIT TO OPERATE AIR POLLUTION SOURCE(S)

If major alterations have occurred, the applicant should complete the Standard Air Permit Application Form.

Source Type: Stationary Renewal of DER Permit No. AO 05-38488

Company Name: Harris Semiconductor County: Brevard

Identify the specific emission point source(s) addressed in this application (i.e., Lime Kiln No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired):

Building 54- East Module Dual Scrubbers

Source Location: Street: Palm Bay Road City: Palm Bay

UTM: East 17-538700 North 17-3100900

Latitude: 28° 01' 20" N. Longitude: 80° 36' 10" W.

1. Attach a check made payable to the Department of Environmental Regulation in accordance with operation permit fee schedule set forth in Florida Administrative Code Rule 17-4.05.
2. Have there been any alterations to the plant since last permitted? Yes No
If minor alterations have occurred, describe on a separate sheet and attach.
3. Attach the last compliance test report required per permit conditions if not submitted previously.
4. Have previous permit conditions been adhered to? Yes No If no, explain on a separate sheet and attach.
5. Has there been any malfunction of the pollution control equipment during tenure of current permit? Yes No If yes, and not previously reported, give brief details and what action was taken on a separate sheet and attach.
6. Has the pollution control equipment been maintained to preserve the collection efficiency last permitted by the Department? Yes No
7. Has the annual operating report for the last calendar year been submitted? Yes No If no, please attach. See Attachments

8. Please provide the following information if applicable:

A. Raw Materials and Chemical Used in Your Process:

Description	Contaminant		Utilization	
	Type	%wt	Rate	lbs/hr
See Attachment A				

B. Product Weight (lbs/hr): N/A

C. Fuels

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	Avg/hr*	Max/hr**	
N/A			

D. Normal Equipment Operating Time: hrs/day 24 ; days/wk 5 ; wks/yr 52 ;
 hrs/yr (power plants only) ; if seasonal, describe

The undersigned owner or authorized representative*** of Harris Semiconductor is fully aware that the statements made in this application for a renewal of a permit to operate an air pollution source are true, correct and complete to the best of his knowledge and belief. Further, the undersigned agrees to maintain and operate the pollution source and pollution control facilities in such a manner as to comply with the provisions of Chapter 403, Florida Statutes, and all the rules and regulations of the Department. He also understands that a permit, if granted by the Department, will be non-transferable and he will promptly notify the Department upon sale or legal transfer of the permitted facility.

*During actual time of operation.

**Units: Natural Gas-MMCF/hr; Fuel Oils-barrels/hr; Coal-lbs/hr.

***Attach letter of authorization if not previously submitted

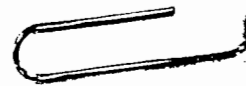
James R. Kolanek
 Signature, Owner or Authorized Representative
 (Notarization is mandatory)
James R. Kolanek Mgr., Environmental Services
 Typed Name and Title
P.O. Box 883 M/S 58-55
 Address
Melbourne Florida 32901
 City State Zip
2/6/86 Date (305) 724-7467 Telephone No.

ATTACHMENT A
 HARRIS SEMICONDUCTOR
 AO 05-38488
 Building 54

<u>Description</u>	<u>Contaminant Type</u>	<u>Wt. (lbs/gal)</u>	<u>Utilization Rate (lbs/hr)</u>
Xylene	VOC	7.03	0.222
Methyl alcohol	Solvent	6.60	0.174
1,1,1, Trichloroethane	VOC	11.25	0.166
Isopropyl Alcohol	Solvent	6.60	0.424
Hydrofluoric Acid	Acid	9.76	0.180
Sulfuric Acid	Acid	15.36	1.144
Hydrochloric Acid	Acid	9.93	0.048
Nitric Acid	Acid	8.85	0.028

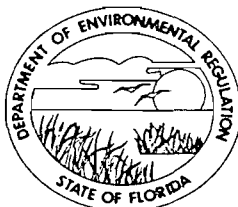
0.986 lbs/hr @ 100% VOC

$$0.986 \text{ lbs/hr} (24)(5)(52) = \frac{6153}{200} = 3.08 \text{ /yr VOC @ } 6240 \text{ lbs/yr}$$



STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32399-2400



BOB MARTINEZ
GOVERNOR
DALE TWACHTMANN
SECRETARY

April 20, 1988

CERTIFIED MAIL - RETURN RECEIPT REQUESTED

Mr. James R. Kolanek
Manager, Environmental Services
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32901

Dear Mr. Kolanek:

Re: Completeness Review of AC 05-147321
Building 54 - Permit Consolidation

The Department received the above referenced application package and your letter dated March 2, 1988, on March 3, 1988. The appropriate fee was received on March 24, 1988. Based on a review of the application package, the package is deemed incomplete and the following information, including all assumptions, calculations and reference material, will have to be submitted to the DER's Bureau of Air Quality Management office so that the status can, again, be ascertained:

1. For the 13% nonproduction VOC reduction due to scrubber efficiency (see Attachment B of the submittal), what is the final disposition of the scrubber effluent? Of the VOC removed, is any of the VOC being reclaimed or recycled? In order to take credit for removal of VOC, it must be proven that the VOC is not released into the atmosphere and it can be quantified (distilling, reclaiming, recycling, etc.) through record keeping.
2. Based on No. 1, is it to be assumed that 87% of the VOC production and nonproduction emissions are being released into the atmosphere without control? If not, please explain.
3. Provide the facility's material balance report, which was to have been completed by this time.
4. Describe and provide how many heated and unheated reservoirs, sinks, or containers containing precursor and nonprecursor organic compounds are there in Building 54? How many of them have adequate covers to prevent release of organic compounds during non-use? What is the freeboard ratio of each?

Mr. James R. Kolanek
Page Two
April 20, 1988

5. Please explain how emissions of VOC are being released during nonproduction hours?
6. What is the current status of the cogeneration project, which was discussed during the February 17, 1988 meeting?

If there are any questions, please call Bruce Mitchell at (904)488-1344 or write to me at the above address.

Sincerely,



C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management

CHF/BM/s

cc: T. Sawicki, CFD
L. Hutker, P.E., Harris Semiconductor
B. Pittman, Esq.



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Bob Martinez, Governor

Dale Twachtmann, Secretary

John Shearer, Assistant Secretary

June 6, 1988

CERTIFIED MAIL - RETURN RECEIPT REQUESTED

Mr. James R. Kolanek
Manager, Environmental Services
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32901

Dear Mr. Kolanek:

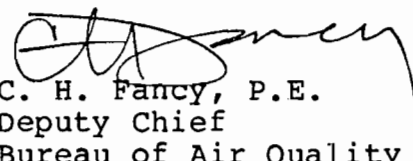
Re: Completeness Review of AC 05-147321
Building 54 - Permit Consolidation

The Department received your letter dated May 13, 1988, as a response to the Department's letter dated April 20, 1988, requesting additional information. Based on the response, the application package is deemed incomplete and the following information, including all assumptions, reference material and calculations, will have to be submitted before the status can, again, be ascertained.

1. Submit the facility's material balance report, which will be used to categorize the facility according to its annual emissions and to assess the emissions from each building.

If there are any questions, please call Bruce Mitchell at (904)488-1344 or write to me at the above address.

Sincerely,


C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management

CHF/BM/s

cc: T. Sawicki, Central FL District
L. Hutker, P.E., Harris Semiconductor
B. Pittman, Esq., DER



RECEIVED

JUL 1 1988

DER-BAQM

June 29, 1988

Mr. C.H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality Management
Florida Department of Environmental Regulation
Twin Towers Office Bldg.
2600 Blair Stone Road
Tallahassee, Florida 32399-2400

Subject: C.H. Fancy Letter of June 6, 1988
Building 54 - Permit Consolidation AC 05-147321

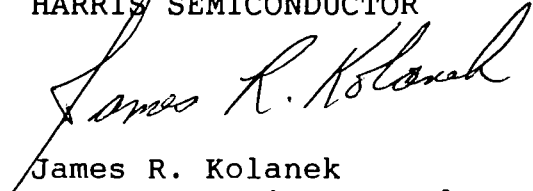
Dear Mr. Fancy:

This letter is in reply to Harris Semiconductors' consolidated permit application AC 05-147321 and your letter of June 6, 1988. Enclosed for your review is the report entitled Harris Semiconductor, 1987 Solvent Material Balance, dated June 27, 1988.

Harris believes that the enclosed report supports our previous position that the annual air emissions from the facility are within the range represented by the permit application. It is our understand that submittal of the enclosed information provides all of the outstanding information requested by the Florida Department of Environmental Regulation.

If you should have any questions about the enclosed information, please call me at (407) 724-7467.

Sincerely,
HARRIS SEMICONDUCTOR



James R. Kolanek
Manager, Environmental Services

c.c. A.T. Sawicki, FDER Orlando

HARRIS SEMICONDUCTOR

1987 SOLVENT MATERIAL BALANCE

JUNE 27, 1988

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COMPUTER DATA BASE		
PURCHASING RECORDS		
CONCLUSIONS AND RECOMMENDATIONS	PAGE	11
ATTACHMENT 1	-	WASTE SHIPMENTS OFF-SITE DATA
ATTACHMENT 2	-	INDUSTRIAL WASTE WATER DISCHARGE DATA
ATTACHMENT 3	-	AIR EMISSIONS DATA
ATTACHMENT 4	-	CHEMICAL USAGE DATA
ATTACHMENT 5	-	WASTE PROFILE

Introduction:

This report addresses the Harris Semiconductor facility and reflects the amounts of all VOC / solvents, purchased, reclaimed, disposed of off-site, discharged in waste water, or released to the atmosphere. This report covers the period of January 1, 1987 through December 31, 1987. All available sources of information were utilized. The following reports and sources of information were used in preparing this report:

- 1.) In-house Accounting Reports
- 2.) In-house COM Stock Reports
- 3.) Harris Waste Profiles
- 4.) Harris Waste Analysis Reports
- 5.) Shipping Manifests
 - a.) Bulk Shipments
 - b.) Drum Shipments
- 6.) ACE Air Monitoring Reports
- 7.) Daily Waste Water Reports
- 8.) Enviropact Lab Reports

The data was evaluated by comparing the chemical purchasing records with the known emission and shipping records. More detailed discussion of the data sources, data evaluation, error analysis, conclusions and recommendations are included in detail later in this report.

SUMMARY:

A similar report was prepared in 1987, which covered the period of calendar year 1986. This was the most comprehensive attempt of this nature made to quantify the volume of VOC / solvents consumed by Harris Semiconductor and to identify their final disposition. Prior to the recent monitoring activities, it had been assumed that most of the chemicals were collected and transported off-site for ultimate disposal. Because the 1986 report, was the first attempt of this magnitude to reconcile this data much of the information was incomplete and suspect. Many of the recommendations proposed in the 1986 report, to improve the accuracy of the information, were implemented or are in the process of being implemented. Many of these improvements have increased the quality and accuracy of the 1987 report, which is far more comprehensive. As a result of these changes it is possible to draw more meaningful conclusions.

The following information is offered as a brief summary of

HARRIS SEMICONDUCTOR
1987 SOLVENT MATERIAL BALANCE
PAGE 4

SUMMARY (cont.):

the detailed data which is included to document these results:

VOC's / Solvents Discharged by Source	
Waste Water	27,000 pounds
Air Emissions	262,000 pounds
Waste Shipments	584,000 pounds
	<hr/>
Total	873,000 pounds
Chemicals Purchased	957,000 pounds
Quantity Variance	84,000 pounds
Percent Variance	8.8 %

A comparison of the data would seem to indicate a high degree of accuracy. The percent variance number is presented for comparative purposes only. The data utilized in computing these figures are the most accurate available. However, there are a number of potential sources of error which would seem to indicate that the actual margin for error is greater than 9 percent. However, it is possible that the various sources of error cancel themselves out and yield a range of error of less than ten percent.

It is Semiconductor's intention to continue to reduce the potential for error in an attempt to continue to improve the quality of the data. A major improvement will be made in 1989 when the Title III SARA regulations require vendors to provide customers with more accurate data on the chemical composition of those chemicals which are purchased and are listed in the SARA regulations. This will improve some of data, but will not totally eliminate the inaccuracies relating to chemical composition due to the fact that not all of the chemicals of concern in this report are on the Title III list of chemicals.

DISCUSSION:

MATERIAL SAFETY DATA SHEETS:

Most of the chemicals used by Semiconductor in its manufacturing processes are not pure chemical compounds, but rather mixtures or trade name chemicals. Therefore, it is necessary to rely on the manufacturers' MSDS to obtain information on the specific components of the process chemicals used.

Many manufacturers consider the exact formulation of their products proprietary and therefore will provide only approximate concentrations for the specific components. The listed range of a particular component can be quite large. For purposes of this report when it was necessary to use a concentration range for a solvent the mid point of the range was used for purposes of calculation. This approach was utilized in an attempt to neither over nor under report on the quantity of chemical purchased.

WASTE PROFILES:

In 1984, Semiconductor began compiling and evaluating detailed chemical profiles of the specific waste streams generated by the manufacturing processes. These profiles are based on in house laboratory analysis. The chemical analysis is used to define a range for the individual components of the various constituents. These profiles are evaluated annually and changed to reflect any significant changes that may have occurred in the manufacturing processes. In addition, to evaluation of existing profiles, new profiles are added when a new process or chemical is introduced which does not fit any existing waste description. At the present time, there are 54 waste profiles that are managed by the environmental staff of Semiconductor.

Attachment 5 contains an example of a typical waste profile. As can be seen from the example, the profiles indicate a minimum and maximum range in percent for the individual constituents of concern. Some of these profiles are for very minor streams which are generated very infrequently. Others are wastes generated on a very regular basis.

WASTE ANALYSIS:

The most accurate data base on waste streams is currently on bulk shipments. Initially, this data base was created to insure the safe shipment of large quantities of chemicals over public roads by licensed transporters. A chemical analysis is performed on every bulk shipment.

These analysis accompany every bulk shipment which leaves the Semiconductor facility. The waste analysis is performed for these components which are likely to be present in the waste stream.

In addition to bulk shipments, Semiconductor collects and ships a significant amount of wastes in fifty-five gallon drums and smaller containers. Drummed wastes are collected at point of use locations and brought to a central location within the facility, where they are checked and temporarily stored prior to shipment. In 1987, Semiconductor shipped off site approximately 300,000 gallons of waste for disposal or recycle. Approximately 60 percent of this was in bulk shipments. The balance was in 55 gallon drums. This averages out to around 120 drums per month. The number of containers generated makes it impractical to analyze samples from every container. Therefore, drummed wastes are spot checked, and random samples are taken for analysis.

WASTE SHIPMENTS:

All shipments leaving Semiconductor's facility, whether sent for recycle or disposal, are accompanied by a Hazardous Waste Uniform Manifest. All current State, EPA, and DOT regulations are followed in the preparation, distribution, and retention of the waste manifests. In addition to the original hard copy retention of these records, detailed information is entered into a computer data base system for record retention, reporting, and tracking purposes. The information contained on the manifests was the primary source of information on those VOC/solvents shipped from Semiconductor for recycle or disposal off-site. Quantities of chemicals leaving the facility in bulk shipment were recorded in gallons based on visual inspection of the tankers before and after they had been filled. Quantities of chemicals leaving the facility in drums were based on an accurate drum count and the assumption that each drum contained 55 gallons of material.

Attachment 1 contains a list of all waste shipments made from Semiconductor during calender year 1987. All waste shipments with the following EPA ID's were included in the calculations:

D001, F001, F002, F003, F004, F005

Waste chemicals with the previous RCRA ID numbers, as a rule, will meet the Florida DER definition of VOCs. There were a number of lab pac shipments which may have met this definition but were not included in the calculation. The total volume of these materials was well under 100 gallons and would have had little if any impact on the outcome of the material balance.

WASTE SHIPMENTS (cont.):

Once the above information was compiled, the waste streams with the appropriate RCRA ID were selected from the waste profile list and compared with the shipping records. Table I was then prepared in order to calculate the quantity of solvents shipped off site. Total pounds shipped were then calculated from the gallons on the shipping records and the specific gravity information on the waste profile. If no specific gravity data was available, then a gravity of 0.9 was assumed. The following is an example of the calculation steps which were followed:

1987 shipments for Stream H005 - 28260 gallons.

$28260 \text{ gal} \times 8.34 \text{ lbs/gal} \times 0.9 \text{ (sg)} = 212,199 \text{ lbs.}$

H005 contains a minimum of 20 % acetone and a maximum of 55% acetone. From the waste profile. See Attachment 5.

$212,000 \text{ lbs} \times 0.20 = 42,400 \text{ lbs acetone min.}$

$212,000 \text{ lbs} \times 0.55 = 116,000 \text{ lbs acetone max.}$

This procedure was then repeated for each component on every waste profile. Like components were then added together to obtain the total quantities for each compound. The mid point quantity for each compound was then calculated. The following example is for acetone.

214,776 lbs of acetone (max.) shipped under all Profiles

79,034 lbs of acetone (min.) shipped under all Profiles

Mid point value = $((214,000 \text{ lbs} - 79,034 \text{ lbs})/2) + 79,034$
= 146,905 lbs of acetone

Once the total pounds of each waste was calculated, this information was used to calculate the quantity of the individual components present in the waste stream. During this stage of the calculation the minimum, maximum, and the calculated mean from the waste profiles was utilized. Using this information, it was determined that the minimum amount of solvents in the waste shipments would have been 266,000 pounds, the maximum amount would have been 901,000 pounds, and the average amount would have been 584,000 pounds. The average amount was used during the remainder of the report for comparison, because it is believed that it most accurately indicates the quantity of VOC/solvents which were shipped from Semiconductor for disposal or recycle.

WASTE WATER DISCHARGE:

Harris Semiconductor discharges it's Treated Industrial Waste Water in accordance with its Underground Injection Control Permit Number UC05-1265191. The industrial water treatment plant collects and treats all industrial water from the semiconductor manufacturing facility. All manufacturing and process support equipment discharges to the treatment plant and ultimately to the industrial deep well. There are no discharges to surface water or to POTWs from the facility. The only water discharged to the local POTW is water from the sanitary facility and cafeterias.

Attachment 2 contains flow and monitoring data from the treatment plant from the period of January 1, 1987 through December 31, 1987. During this time period the facility treated approximately 433 million gallons of water. Between February and December of 1987, Semiconductor monitored the waste water treatment plant to quantify potential VOC emissions. During this period, the samples were collected on a weekly basis and analyzed using EPA Methods 624 and 625 for priority pollutants and an additional selection of other compounds. Specifically, methanol, acetone, and IPA were also evaluated. Table II contains all of the parameters which had at least one positive response during the study. The average observed concentration was then utilized with the volume of water discharged to calculate the quantity of solvents which were discharge during the course of the year.

Table III lists the parameters which were included. The average flows during the month were used to calculate the quantity of solvents which were discharged during the respective months. These monthly volumes were then totaled to obtain the annual quantity discharged. The following is an example of the calculations which were utilized:

$$\begin{aligned} \text{Average concentration of Acetone} &= 3538 \text{ ppb} \\ &= 3.54 \text{ ppm} \end{aligned}$$

$$3.54 \text{ ppb} \times 8.34 \text{ lbs / gal} \times 33.006 \text{ Mil Gal (jan)} = 937.9 \text{ lbs}$$

The above calculation was then repeated for each month of 1987. The monthly totals were then added. This same procedure was repeated for each parameter.

The information obtained indicated that during 1987 approximately 27,000 pounds of solvents were discharged in the industrial waste water. It should be noted that the trihalomethanes which were listed on table II, were present in the incoming water from the local drinking water utility.

These materials are not used in the manufacturing areas. Therefore, the loading of these compounds was not included in the 27,000 pounds which were calculated.

AIR EMISSIONS:

Between December 1986 and December 1987, Harris Semiconductor performed extensive monitoring of its point source discharges. Twenty one (21) different discharge points were monitored. Every point was monitored at least once during the monitoring program. In an attempt to evaluate the reliability of the monitoring results several of the larger sources were monitored more than once. Efforts were also taken to determine if there were any VOC / solvent emissions during the non-production hours. To accomplish this one source was monitoring on a Sunday when no production activities were scheduled.

All of the monitoring was performed by Air Consulting Engineers of Gainseville. Two different methods were employed. Method 25A utilizing a Flame Ionization Detector was the primary method of analysis. This method was selected because it was anticipated that due to the nature of the semiconductor manufacturing methods there would be very noticeable changes in the quantity of VOC emissions during the course of a normal shift. Some monitoring utilizing Total Organic Vapor collection tubes and GC/MS laboratory analysis to determine the exact chemical composition of the air stream was also performed. For the purposes of this report, Method 25A was superior because it enabled Harris to quantify the amount of VOCs which were being emitted far more accurately than the GC/MS. The on line monitoring capability of the FID allowed for the more accurate determination of the amount of VOC compounds which were potentially discharged over the course of the year.

Attachment 3 contains a list of the emission sources that were monitored during the course of the year along with the projected quantity of emissions which was calculated for each source. The emissions numbers were calculated utilizing the observed VOC emissions and the actual production schedule for the corresponding source. In addition, the observed non-production emissions loading was factored into the total yearly loading for each source. Based on the monitoring which was performed it was determined that the total emissions from the facility were approximately 262,000 pounds.

CHEMICAL INVENTORY:

During the months of December 1986 and January 1987, Harris Semiconductor conducted a detailed physical inventory of all chemicals currently in use at the facility.

This information has become the baseline for all process and process support chemicals used at the Palm Bay facility. This inventory was a joint project between Harris personnel in the Environmental, Health and Safety, and Quality Control Departments.

This survey became the basis for Semiconductors Master Chemical Inventory Data Base. This Data Base contains at the present time in excess of 2500 "chemicals". This does not mean that 2500 compounds are currently in use at the facility. Instead, it means that 2500 chemical names must be managed. This problem is caused by the use of trade name chemicals. More than one half of the chemicals used at Semiconductor are Trade Name Chemicals. The chemicals are generally a mixture of several components. This results in a compounding effect when the information is interred into a data management system. For example, Harris may use 10 trade name chemicals which all have the same four components in varying concentrations. This will result not in the management of four or ten chemicals but fourteen different chemicals.

Once all the chemicals had been identified the project of determining the quantity of each used during 1987 was first undertaken. The first attempt at this project was to utilize receiving records from the Shipping and Receiving Department. After overcoming several computer problems encountered retrieving the data, it was confirmed that only those chemicals entering the facility on the COM Stock system were included in the data base which was being recovered. This required utilization of an alternate data base to accomplish the objective. The Purchase Order Data Base was utilized to obtain the required information.

All information on materials from known chemical vendors and materials containing an appropriate chemical commodity code were recovered for the period of January 1, 1987 through December 31, 1987. Once this information had been obtained the "chemicals" had to be converted to appropriate units of measurement. The chemical records contain various units of measurement (i.e. gallons, pints, cubic feet, pounds, kilograms, drums, cases, etc.). These had to be converted to a common unit of measurement.

After recovery and conversion of the data described above, the most complicated part of the project had to be undertaken. This was the conversion of the trade name chemicals into their appropriate components. This was accomplished by loading the purchase records into the Chemical Inventory Data Base which lists the components for all chemicals and their known or estimated concentration. This part of the project was complicated by the fact that the material description from the purchasing records was not always exactly the same as the description in the chemical data base. This resulted in the need for a great deal of manual confirmation and data entry in order to load the purchased amounts into the computer data base system. This part of the program could be significantly improved if a unique code could be included on the purchase orders and matched to an exact code in the chemical data base system.

Once the above work had been accomplished, the information presented on Tables IV and V was tabulated. Once this information had been compiled, the raw data was reviewed and a determination was made as to whether or not the material was a solvent. Those chemicals which were determined to be solvents were assigned a code of "S". The data base was then sorted and totaled for all compounds which were identified as solvents. The chemicals listed on Table IV totaled 277,372 pounds of solvents received at the facility. The chemicals listed on Table V totaled 679,415 pounds of solvents received at the facility. This resulted in a total of approximately 957,000 pounds of solvents being received by Semiconductor during 1987. As a point of information, two tables are presented in this section because the chemicals on Table V were being reported in the facility's July 1, 1988 Title III SARA report. It was therefore easier to list these tables separately than to combine the data.

The accuracy of this information is primarily limited by the accuracy of the component concentration available from the vendors on trade name chemicals. As the accuracy of this information the accuracy of the chemical data base should also improve.

It was assumed during the course of this material balance that no net increase or decrease in the physical on site inventory took place during the course of the year. In other words it was assumed that the volume of chemicals received were used. Harris Semiconductor has extended significant amounts of time and energy in recent years in programs, such as JIT, to control inventories of materials. Just in Time (JIT) is the principle of delivering the material to the facility and work area just prior to the time that it is needed. This eliminates the need for large inventories of materials in the work place.

CONCLUSIONS AND RECOMMENDATIONS:

This report has been prepared and submitted to the Department of Environmental Regulations in accordance with Harris' previous agreements with the Department. The report has been prepared with the most accurate information available. Harris believes that the information accurately represents the VOC/solvents which were used and their ultimate disposition.

Harris believes that the air emissions data and the waste water discharge data is the most accurate data available. This information is based on actual monitoring data. Only a very limited number of required assumptions were employed. Harris intends to continue with its in house monitoring programs in these two areas. Very few modifications to the procedures are anticipated. Based on prior monitoring and other technical information, Harris is confident that the most accurate method of quantifying the facilities actual emissions is through a technically sound monitoring program.

The hazardous waste data is accurate within the range of assumptions that were made. If any errors have been made in the evaluation of the data, it has been on the conservative side. In other words, if any inaccuracies exist they have been on the side of underestimating the quantities of VOC/solvents which were sent off-site for disposal or recycling. Harris has plans to improve the accuracy in this area by more frequent analysis of drummed waste and the development of a computer data base system for the waste profile analysis.

The chemical data to the best of our knowledge is as accurate as is possible. The areas where we would like to see the most improvement, are the quality of the information on trade name chemicals and our ability to more easily retrieve the data from our internal information systems. Harris environmental, purchasing, accounting, safety, and MIS personnel will be meeting in the near future in an effort to reduce the problems we have encountered in the retrieval of the data. A far more difficult problem is the issue of trade name chemicals. As was indicated in the report, this will improve slightly the vendors are required to provide information on concentrations for chemicals on the SARA list. This problem will undoubtedly will be an issue for many years. Until manufacturers provide more accurate information on the concentrations of VOC/solvents the quality of our data cannot be improved. Unfortunately, any real improvements, in this area, are outside of Harris' control.

HARRIS SEMICONDUCTOR
CALENDAR YEAR 1987
VOC - MATERIAL BALANCE
ATTACHMENT 1
WASTE SHIPMENTS OFFSITE

COMPOUND	HARRIS ID COMMON NAME	H005 MIX SOLV	H010 RESIST	H011 MICRO	H012 TRICH	H013 FREQN	H025 WAT/SOLV	H026 MIX SOLV	H039 1165	H040 MARKEN	H041 ACET/TRI	H042 GLYCER	H43 WAT/MICRORESIST	H045	TOTAL AMOUNT SHIPPED	Min.	Max.	Avg.
	1987 GALLONS	28260	9955	23980	1320	2530	16904	10725	55	55	55	165	5115	440	191559			
	1987 TONS	106	31.5	99.9	7.2	13.8	78.8	39.5	0.25	0.25	0.28		21.3	0.24	399.02			
	1987 POUNDS	212000	63000	199800	14400	27600	157600	79000	500	500	560	0	42600	480	798040			
ACETONE		42400	630	19980	0	0	0	15800	0	0	224	0	0	0	79034			
		116600	6300	59940	0	0	0	31600	0	0	336	0	0	0		214775	146905	
METHANOL		21200	630	0	0	0	1576	3950	0	0	0	0	0	0	27356			
		84800	3150	0	0	0	7880	19750	0	0	0	0	0	0		115580	71468	
IPA		21200	0	0	0	0	1576	3950	0	0	0	0	0	0	26726			
		84800	0	0	0	0	7880	19750	0	0	0	0	0	0		112430	69578	
N-BUTYL ACETATE		4240	630	0	0	0	0	0	10	150	0	0	0	0	5030			
		84800	3150	0	0	0	0	0	25	200	0	0	0	0		88175	46603	
CELLOSOLVE ACE		2120	25200	1998	0	0	1576	790	1	5	0	0	0	0	31690			
		10600	44100	9990	0	0	7880	3950	10	15	0	0	0	0		76545	54117	
XYLENE		2120	9450	1998	0	0	0	3950	0	0	0	0	0	0	17518			
		21200	25200	9990	0	0	0	7900	0	0	0	0	0	0		64290	40904	
TOLUENE		2120	0	0	0	0	0	0	0	0	0	0	0	0	2120			
		21200	0	0	0	0	0	0	0	0	0	0	0	0		21200	11660	
HMDS		0	0	0	0	0	0	3950	0	0	0	0	0	0	3950			
		0	0	0	0	0	0	3950	0	0	0	0	0	0		3950	3950	
ETHYL ACETATE		0	0	0	0	0	0	0	0	0	0	0	0	0	0			
		0	0	0	0	0	0	0	0	0	0	0	0	0		0	0	
FREQN		0	0	0	0	26220	0	1580	0	0	0	0	0	0	27300			
		0	0	0	0	26220	0	7900	0	0	0	0	0	0		34120	30960	
TRICHLOROETHANE		0	0	0	11520	0	0	3950	0	0	224	0	0	0	15694			
		0	0	0	11520	0	0	7900	0	0	336	0	0	0		19756	17725	
PERCH		0	0	1998	0	0	0	0	0	0	0	0	0	0	1998			
		0	0	19980	0	0	0	0	0	0	0	0	0	0		19980	10989	
AROMATICS		3180	0	1998	0	0	0	0	0	0	0	0	0	0	5178			
		21200	0	9990	0	0	0	0	0	0	0	0	0	0		31190	18184	
ALAPHATICS		3180	630	1998	0	0	0	0	0	0	0	0	0	0	5808			
		21200	6300	9990	0	0	0	0	0	0	0	0	0	0		37490	21649	
MISC.		2120	0	9990	0	0	0	3950	425	5	0	0	0	0	16490			
		10600	0	29970	0	0	0	19750	475	15	0	0	852	0		61662	39076	

MINIMUM SHIPPED (LBS.) 266392
MAXIMUM SHIPPED (LBS.) 901144
AVERAGE SHIPPED (LBS.) 583768

TABLE I

HARRIS SEMICONDUCTOR
1987 ANNUAL RCRA REPORT

<u>date</u>	<u>transporter</u>	<u>tsdf</u>	<u>common name</u>	<u>dot description</u>	<u>dot class</u>	<u>un/na</u>	<u>epa id</u>	<u>gallons</u>
10-Sep-87	hwc		diesel	na	na	na	na	55.00
-- Count								1
-- Sum								55.00
29-Sep-87	hwc		used oil	na	na	na	na	165.00
21-May-87	hwc		used oil	na	combust.	na	na	55.00
14-Oct-87	hwc		used oil	na	na	na	na	55.00
02-Jun-87	hwc		used oil	na	combust.	na1270	na	110.00
19-Jun-87	hwc		used oil	na	combust.	na1270	na	110.00
13-Jan-87	hwc		used oil	na	na	na	na	220.00
07-Jul-87	hwc		used oil	na	na	un2710	na	55.00
07-Apr-87	hwc		used oil	na	na	na	na	495.00
05-May-87	hwc		used oil	na	na	na	na	55.00
10-Mar-87	hwc		used oil	na	na	na	na	55.00
-- Count								10
-- Sum								1375.00
02-Jun-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	110.00
08-Dec-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	110.00
27-Jan-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	165.00
24-Nov-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	55.00
07-Jul-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-a	na9189	f001	110.00
10-Nov-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	220.00
14-Oct-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	220.00
07-Apr-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	110.00
13-Jan-87	hwc	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f002	110.00
22-Sep-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	110.00
25-Aug-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-a	na9189	f001	275.00
22-Dec-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	165.00
19-Jun-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-a	na9189	f001	110.00
17-Feb-87	hwc	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	110.00
10-Mar-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	275.00
24-Mar-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	110.00
29-Sep-87	hwc,allw	allworth	freon	hazardous waste liquid, nos	ora-e	na9189	f001	165.00
-- Count								17
-- Sum								2530.00
10-Mar-87	hwc,allw	allworth	glycerine	waste glycerine	non-haz	na	na	165.00
-- Count								1
-- Sum								165.00
18-Jun-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	4500.00
22-Dec-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	385.00

HARRIS SEMICONDUCTOR
1987 ANNUAL RCRA REPORT

date	transporter	tsdf	common name	dot description	dot class	un/na	epa id	gallons
25-Aug-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	495.00
29-Sep-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	110.00
10-Nov-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	55.00
14-Oct-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	220.00
13-Jan-87	hwc	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	715.00
24-Nov-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f001	440.00
15-Sep-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	6000.00
04-Aug-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f001	1375.00
21-Jul-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	715.00
04-Aug-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f001	55.00
04-Aug-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f001	110.00
10-Nov-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	660.00
10-Feb-87	hwc	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	6000.00
10-Sep-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	495.00
12-Aug-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	275.00
14-Dec-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	5760.00
27-Oct-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	770.00
29-Sep-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	495.00
27-Oct-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	165.00
08-Dec-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	330.00
27-Jan-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	550.00
22-Sep-87	hwc,allw	allworth	mixed solv	waste flammable liquid, nos	flammable	un1993	f003,5	110.00

-- Count -----
24

-- Sum -----
30785.00 ✓

10-Nov-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	385.00
10-Mar-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	660.00
24-Mar-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	660.00
27-Oct-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	440.00
17-Feb-87	hwc	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	660.00
19-Jun-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	660.00
05-May-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	550.00
08-Dec-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	165.00
29-Sep-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	275.00
21-May-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	330.00
13-Jan-87	hwc	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	440.00
04-Aug-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	f001	220.00
22-Dec-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	440.00
22-Sep-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	220.00
24-Nov-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	330.00
07-Jul-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	385.00
27-Jan-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	385.00
25-Aug-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	440.00
02-Jun-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	330.00
12-Aug-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	330.00
21-Jul-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	440.00
14-Oct-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	550.00
07-Apr-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	d001	385.00
10-Sep-87	hwc,allw	allworth	resist	waste flammable liquid, nos	flammable	un1993	f003,5	275.00

-- Count -----
24

HARRIS SEMICONDUCTOR
1987 ANNUAL RCRA REPORT

<u>date</u>	<u>transporter</u>	<u>tsdf</u>	<u>common name</u>	<u>dot description</u>	<u>dot class</u>	<u>un/na</u>	<u>epa id</u>	<u>gallons</u>
-- Sum								9955.00 ✓
17-Feb-87	hwc	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	55.00
24-Mar-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	55.00
07-Jul-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-e	un2831	f001	110.00
22-Dec-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	165.00
22-Sep-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	110.00
13-Jan-87	hwc	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	55.00
25-Aug-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-e	un2831	f001	110.00
08-Dec-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	55.00
24-Nov-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	165.00
02-Jun-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2381	f001	55.00
05-May-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	55.00
14-Oct-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	110.00
10-Mar-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-a	un2831	f001	55.00
19-Jun-87	hwc,allw	allworth	trich	waste 1,1,1 trichloroethane	ora-e	un2381	f001	165.00
-- Count								14
-- Sum								1320.00 ✓
10-Sep-87	hwc,allw	allworth	used oil	na	na	na	na	55.00
-- Count								1
-- Sum								55.00
29-Sep-87	hwc	bayou metal	solder					110.00
-- Count								1
-- Sum								110.00
16-Apr-87	chem con	chem con	microstrip	waste flaa., liq., corr., nos flaaaable		un2924	d001,3	4840.00
-- Count								1
-- Sum								4840.00
06-May-87	chem con	chem met	microstrip	waste corrosive liquid, nos	corrosive	un1760	d002	385.00
30-Jun-87	chem con	chem met	microstrip	waste corrosive liquid, nos	corrosive	un1760	d002	385.00
26-May-87	chem con	chem met	microstrip	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
-- Count								3
-- Sum								935.00 ✓
10-Sep-87	chem con	chem met	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	4700.00

HARRIS SEMICONDUCTOR
1987 ANNUAL RCRA REPORT

<u>date</u>	<u>transporter</u>	<u>tsdf</u>	<u>common name</u>	<u>dot description</u>	<u>dot class</u>	<u>un/na</u>	<u>epa id</u>	<u>gallons</u>

-- Count								1

-- Sum								4700.00 ✓

28-Jan-87	chem con	chem set	mixed hf	waste acid liquid, nos	corrosive	un1760	d002	4500.00
29-May-87	chem con	chem set	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4900.00
13-Jan-87	chem con	chem set	mixed hf	waste acid liquid, nos	corrosive	un1760	d002	4500.00

-- Count								3

-- Sum								13900.00 ✓

02-Sep-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	385.00
24-Nov-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	110.00
10-Nov-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	220.00
17-Feb-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	495.00
15-Dec-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	220.00
27-Oct-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	330.00
11-Mar-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	275.00
05-Apr-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	220.00
29-Sep-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	330.00
31-Jul-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	220.00
14-Jan-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	1155.00
16-Oct-87	chem con	chem set	water/micro	waste corrosive liquid, nos	corrosive	un1760	d002	220.00

-- Count								12

-- Sum								4180.00 ✓

16-Mar-87	cwm	cwm	ammou persul	waste ammonium persulfate	oxidizer	un1444	na	55.00

-- Count								1

-- Sum								55.00

15-Sep-87	cwm	cwm	arsen cont	hazardous waste solid, nos	orm-e	na9189	d4,6,7,8,	220.00
18-Jun-87	cwm	cwm	arsen cont	hazardous waste solid, nos	orm-e	na9189	d467B11	165.00
12-Feb-87	cwm	cwm	arsen cont	hazardous waste solid, nos	orm-e	na9189	d4,6,7,8,	165.00
16-Mar-87	cwm	cwm	arsen cont	hazardous waste solid, nos	orm-e	na9189	d467B11	110.00

-- Count								4

-- Sum								660.00

15-Sep-87	cwm	cwm	chrom triox	waste acid liquid, nos	corrosive	na1760	d002,7	220.00
12-Feb-87	cwm	cwm	chrom triox	waste acid liquid, nos	corrosive	na1760	d002,7	110.00
18-Jun-87	cwm	cwm	chrom triox	waste acid liquid, nos	corrosive	na1760	d002,7	165.00
16-Mar-87	cwm	cwm	chrom triox	waste acid liquid, nos	corrosive	na1760	d002,7	55.00

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-- Count								4

-- Sum								550.00

15-Jan-87	chem con	cwa	cont. soil	hazardous waste solid, nos	ora-e	na9189	na	0.00
19-Jan-87	chem con	cwa	cont. soil	Hazardous waste solid, nos	ora-e	na9189	na	0.00
19-Jan-87	chem con	cwa	cont. soil	Hazardous waste solid, nos	ora-e	na9189	na	0.00
15-Jan-87	chem con	cwa	cont. soil	hazardous waste solid, nos	ora-e	na9189	na	0.00

-- Count								4

-- Sum								0.00

23-Dec-87	cwa	cwa	copp sulf	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
16-Mar-87	cwa	cwa	copp sulf	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
18-Jun-87	cwa	cwa	copp sulf	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
12-Feb-87	cwa	cwa	copp sulf	waste corrosive liquid, nos	un1760	un1760	d002	55.00

-- Count								4

-- Sum								220.00

16-Mar-87	cwa	cwa	diesel/soil	hazardous waste solid, nos	ora-e	na9189	na	110.00

-- Count								1

-- Sum								110.00

16-Mar-87	cwa	cwa	hcl	waste hydrochloric acid	corrosive	un1789	d002	55.00

-- Count								1

-- Sum								55.00

15-Sep-87	cwa	cwa	lab pac	waste potassium permanganate	oxidizer	un1490	d001	55.00
15-Sep-87	cwa	cwa	lab pac	hazardous waste liquid, nos	ora-e	na9189	u122	55.00
15-Sep-87	cwa	cwa	lab pac	waste flammable liquid, nos	flammable	un1993	d1,3,u002	55.00
15-Sep-87	cwa	cwa	lab pac	hazardous waste solid, nos	ora-e	na9189	d006	55.00
15-Sep-87	cwa	cwa	lab pac	non hazardous waste	na	na	na	55.00
15-Sep-87	cwa	cwa	lab pac	waste corrosive liquid, nos	corrosive	un1760	d002,u052	55.00
15-Sep-87	cwa	cwa	lab pac	waste poisonous liquid, nos	poison b	un2810	p106,d004	55.00
15-Sep-87	cwa	cwa	lab pac	waste corrosive liquid, nos	corrosive	un1760	d002,3	55.00
15-Sep-87	cwa	cwa	lab pac	waste carbon tetrachloride	ora-a	na1846	u211	110.00
15-Sep-87	cwa	cwa	lab pac	waste corrosive liquid, nos	corrosive	un1760	d002	110.00
15-Sep-87	cwa	cwa	lab pac	waste methylene chloride	ora-a	un1593	u080	110.00
15-Sep-87	cwa	cwa	lab pac	hazardous waste liquid, nos	ora-e	na9189	d007	55.00
15-Sep-87	cwa	cwa	lab pac	waste chloroform	ora-a	un1888	u044	55.00
15-Sep-87	cwa	cwa	lab pac	hazardous waste liquid, nos	ora-e	na9189	d008	55.00
15-Sep-87	cwa	cwa	lab pac	waste ora-a, nos	ora-a	na1693	u211,u044	110.00

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15-Sep-87	cwa	cwa	lab pac	waste flammable liquid, nos	flammable	un1993	u162,d1,3	55.00
15-Sep-87	cwa	cwa	lab pac	waste battery, wet	corrosive	un2794	d002	110.00
15-Sep-87	cwa	cwa	lab pac					116.00
15-Sep-87	cwa	cwa	lab pac	waste oxidizer, nos	oxidizer	un1479	d001,3	55.00
15-Sep-87	cwa	cwa	lab pac	non hazardous waste	na	na	na	55.00
15-Sep-87	cwa	cwa	lab pac	waste battery, wet	corrosive	un2795	d002	55.00
15-Sep-87	cwa	cwa	lab pac	waste alkaline liquid, nos	corrosive	na1719	d002	55.00
15-Sep-87	cwa	cwa	lab pac	waste flammable liquid, nos	flammable	un1993	d001	55.00

-- Count -----
23

-- Sum -----
1601.00

15-Sep-87	cwa	cwa	mercury	waste mercury metallic	ora-b	un2809	d009,u151	110.00
18-Jun-87	cwa	cwa	mercury	waste mercury metallic	ora-b	na2809	d009	110.00

-- Count -----
2

-- Sum -----
220.00

18-Jun-87	cwa	cwa	mixed solv	waste flammable liquid, nos	flammable	un1993	f001,3	880.00
16-Mar-87	cwa	cwa	mixed solv	waste flammable liquid, nos	flammable	un1993	f001,3	1320.00

-- Count -----
2

-- Sum -----
2200.00

19-Jun-87	cwa	cwa	phosp	waste phosphorus, amorphous	flammable	un1338	d001	55.00
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-- Count -----
1

-- Sum -----
55.00

13-Jan-87	chem con	cwa	soil	hazardous waste solid, nos	ora-e	na9189	na	0.00
13-Jan-87	chem con	cwa	soil	hazardous waste solid, nos	ora-e	na9189	na	0.00

-- Count -----
2

-- Sum -----
0.00

15-Sep-87	cwa	cwa	tin plate	waste sulfuric acid, spent	corrosive	un1832	d002,8	275.00
18-Jun-87	cwa	cwa	tin plate	waste sulfuric acid, spent	corrosive	un1832	d002,8	220.00
12-Feb-87	cwa	cwa	tin plate	waste sulfuric acid, spent	corrosive	un1832	d002,8	330.00
23-Dec-87	cwa	cwa	tin plate	waste sulfuric acid, spent	corrosive	un1832	d002,7	220.00
16-Mar-87	cwa	cwa	tin plate	waste sulfuric acid, spent	corrosive	un1832	d002,8	275.00

-- Count -----
5

-- Sum -----
1320.00

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23-Apr-87	chem con	cwa	water/solv	hazardous waste liquid, nos	ora-e	na9189	f001	3500.00
23-Dec-87	cwa	cwa	water/solv	hazardous waste liquid, nos	ora-e	na9189	f003	990.00
04-Mar-87	chem con	cwa	water/solv	hazardous waste liquid, nos	ora-e	na9189	f003	5000.00
12-Feb-87	cwa	cwa	water/solv	hazardous waste liquid, nos	gem-e	na9189	f003	990.00
16-Feb-87	chem con	cwa	water/solv	hazardous waste liquid, nos	ora-e	na9189	f003	5000.00
16-Mar-87	cwa	cwa	water/solv	hazardous waste liquid, nos	ora-e	na9189	f003	330.00
03-Aug-87	chem con	cwa	water/solv	hazardous waste liquid, nos	ora-e	na9189	f003	3094.00
-- Count -----								7
-- Sum -----								18904.00
07-Oct-87	cyl recon	cyl recon	bf3 cyl	waste boron trifluoride	non flam	un1008	d002	0.00
-- Count -----								1
-- Sum -----								0.00
07-Oct-87	cyl recon	cyl recon	cl2 cyl	waste chlorine	non flam	un1017	d002	0.00
-- Count -----								1
-- Sum -----								0.00
07-Oct-87	cyl recon	cyl recon	h2s cyl	waste hydrogen sulfide	flammable	un1053	u135	0.00
-- Count -----								1
-- Sum -----								0.00
07-Oct-87	cyl recon	cyl recon	n2 cyl	waste nitrogen	non flam	un1066	x905	0.00
-- Count -----								1
-- Sum -----								0.00
24-Feb-87	chem con	eei	1165	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
-- Count -----								1
-- Sum -----								55.00
11-Mar-87	chem con	eei	8050	waste flammable liquid, nos	flammable	un1993	d001	55.00
-- Count -----								1
-- Sum -----								55.00

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14-Jan-87	chem con	eei	acet/tric	waste flammable liquid, nos	flammable	un1993	d001	55.00
-- Count -----								1
-- Sum -----								55.00
24-Feb-87	chem con	eei	cool twr sld	hazardous waste solid, nos	ora-e	na9189	d002	605.00
-- Count -----								1
-- Sum -----								605.00
24-Nov-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1265.00
16-Oct-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1100.00
17-Feb-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1705.00
10-Nov-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	990.00
24-Feb-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	330.00
26-May-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002,6	770.00
29-Sep-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1155.00
30-Jun-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002,6	1595.00
27-Oct-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	715.00
31-Jul-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1210.00
03-Apr-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002,6	1265.00
11-Mar-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002,006	550.00
06-May-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002,6	1210.00
15-Dec-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1265.00
02-Sep-87	chem con	eei	developer	waste corrosive liquid, nos	corrosive	un1760	d002	1210.00
-- Count -----								15
-- Sum -----								16335.00
02-Sep-87	chem con	eei	fixer	hazardous waste liquid, nos	corrosive	na9189	d006,11	55.00
30-Jun-87	chem con	eei	fixer	hazardous waste liquid, nos	ora-e	na9189	d006,11	55.00
26-May-87	chem con	eei	fixer	hazardous waste liquid, nos	ora-e	na9189	d006,11	55.00
03-Apr-87	chem con	eei	fixer	hazardous waste liquid, nos	ora-e	na1989	d006,11	55.00
29-Sep-87	chem con	eei	fixer	hazardous waste liquid, nos	ora-e	na9189	d006,11	55.00
14-Jan-87	chem con	eei	fixer	hazardous waste liquid, nos	ora-e	na9189	d006,011	110.00
-- Count -----								6
-- Sum -----								385.00
14-Jan-87	chem con	eei	formal.	waste formaldehyde solution	ora-a	un2209	na	330.00
29-Sep-87	chem con	eei	formal.	waste formaldehyde solution	ora-a	na9189	na	55.00
-- Count -----								2
-- Sum -----								385.00

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29-Sep-87	chem con	eei	markea	waste flammable liquid, nos	flammable	un1993	d001	55.00
14-Jan-87	chem con	eei	markea	waste flammable liquid, nos	flammable	un1993	d001	165.00
-- Count -----								2
-- Sum -----								220.00
24-Nov-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	825.00
16-Oct-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	2310.00
15-Dec-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	1100.00
14-Jan-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,002	2090.00
27-Oct-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un1924	d001,2	605.00
15-Oct-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	1980.00
10-Nov-87	chem con	eei	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	715.00
-- Count -----								7
-- Sum -----								9625.00 ✓
11-Nov-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	5000.00
16-Dec-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	5000.00
26-May-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002,8	55.00
21-Apr-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	4700.00
25-Sep-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	4700.00
11-Mar-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	un1760	d002	55.00
19-Oct-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	un1760	d002	5000.00
14-May-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	4700.00
02-Sep-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002,8	55.00
15-Jul-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	4700.00
14-Jan-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	un1760	d002	110.00
19-Mar-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	na1760	d002	4500.00
11-Aug-87	chem con	eei	mixed acid	waste acid liquid, nos	corrosive	un1760	d002	4700.00
-- Count -----								13
-- Sum -----								43275.00 ✓
18-Feb-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4700.00
05-May-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4800.00
12-Mar-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4700.00
13-Jul-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4500.00
05-Nov-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
18-Nov-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4300.00
21-Oct-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
14-Dec-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
29-Jul-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
25-Feb-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	0.00
10-Jun-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
04-Jun-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
14-Apr-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4800.00
08-Sep-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4700.00
20-Aug-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5275.00

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01-Oct-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4700.00
25-Mar-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	4900.00
03-Mar-87	chem con	eei	mixed hf	waste acid liquid, nos	corrosive	na1760	d002	5000.00
-- Count -----								18
-- Sum -----								82375.00
14-Jan-87	chem con	eei	scrub sld	hazardous waste solid, nos	ora-e	na9189	na	220.00
-- Count -----								1
-- Sum -----								220.00
24-Nov-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
15-Dec-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
31-Jul-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
02-Sep-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
14-Jan-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
11-Mar-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
03-Apr-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	110.00
24-Feb-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	55.00
26-May-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
17-Feb-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	110.00
14-Jan-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
27-Oct-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
30-Jun-87	chem con	eei	shipley	waste corrosive liquid, nos	corrosive	un1760	d002	165.00
-- Count -----								13
-- Sum -----								1485.00
10-Jul-87	chem con	eei	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
-- Count -----								1
-- Sum -----								3200.00
10-Aug-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
01-May-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	0.00
10-Nov-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
09-Oct-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
17-Mar-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
27-Aug-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3300.00
16-Feb-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
21-May-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
13-Feb-87	chem con	farmland	sulfuric	waste sulfuric acid	corrosive	un1830	d002	3200.00
-- Count -----								9
-- Sum -----								25700.00

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12-Aug-87	hwc	marine shale	flam solid	waste flammable solid, nos	flammable	un1993	d001	110.00
-- Count -----								1
-- Sum -----								110.00
19-Jun-87	hwc	marine shale	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	4510.00
15-Jun-87	chem con	marine shale	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	4840.00
19-Jun-87	hwc	marine shale	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	660.00
08-Sep-87	hwc	marine shale	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	1980.00
31-Jul-87	chem con	marine shale	microstrip	waste flam., liq., corr., nos	flammable	un2924	d001,2	2365.00
-- Count -----								5
-- Sum -----								14355.00 ✓
12-Aug-87	hwc	marine shale	paint	waste flammable solid, nos	flammable	UN1325	d001	87.00
10-Nov-87	hwc	marine shale	paint	waste flammable liquid, nos	flammable	un1993	d001	55.00
-- Count -----								2
-- Sum -----								142.00
12-Aug-87	hwc	marine shale	resist bags	waste flammable liquid, nos	flammable	UN1325	d001	220.00
10-Nov-87	hwc	marine shale	resist bags	waste flammable solid, nos	flammable	un1325	d001	110.00
12-Aug-87	hwc	marine shale	resist bags	waste flammable liquid, nos	flammable	UN1325	d001	110.00
-- Count -----								3
-- Sum -----								440.00
13-Jan-87	hwc	solid tek	developer	waste corrosive liquid, nos	corrosive	na9189	na	715.00
-- Count -----								1
-- Sum -----								715.00
17-Feb-87	hwc	solid tek	nick strip	waste corrosive liquid, nos	corrosive	un1760	d002,8	55.00
-- Count -----								1
-- Sum -----								55.00
04-Mar-87	amer chem	suttles	cyanide	waste cyanide solution, nos	poison b	un1935	f007	55.00
-- Count -----								1
-- Sum -----								55.00

HARRIS SEMICONDUCTOR
 1987 ANNUAL RCRA REPORT

<u>date</u>	<u>transporter</u>	<u>tsdf</u>	<u>common name</u>	<u>dot description</u>	<u>dot class</u>	<u>un/na</u>	<u>epa id</u>	<u>gallons</u>
28-Apr-87	chem con	trical	mixed solv	waste flammable liquid, nos	flammable	un1993	d001	6000.00
-- Count -----								1
-- Sum -----								6000.00
== Count =====								284
== Sum =====								306702.00

*HARRIS SEMICONDUCTOR
CALENDAR YEAR 1987
VOC – MATERIAL BALANCE
ATTACHMENT 2
INDUSTRIAL WASTEWATER DISCHARGE*

DATE	CHLOROFORM		BROMODICHLORO-METHANE		DIBROMOCHLORO-METHANE		1,2-DICHLORO-BENZENE		1,4-DICHLORO-BENZENE		ETHYL BENZENE		TETRACHLOROETHENE		TRICHLORO-ETHANE		XYLENE		METHANOL		ACETONE		IPA		VINYL CHLORIDE		
	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	INFL.	EFFL.	
13-Feb-87		41		7.8		0		0		0		0		0		0		0				1000					0
20-Apr-87	4.1	5.2	0	8.9	2.9	7.8	0	0	5	0	0	0	0	0	1.4	0	1.4	3.7	2600	7500	5400	1700	3500	2000	0	0	
01-May-87	5.3	0	0	0	5.7	10	241	177	0	0	7	0	46	7.8	1.9	0	8.3	31	3300	3100	13300	24600	1800	1300	0	0	
13-Aug-87	3	3	0	2	0	2	0	0	0	0	0	0	0	0	2	0	9	0	<1000	<1000	<250	840	<250	<250	0	0	
20-Aug-87	11	2	0	2	11	2	0	0	0	0	0	0	0	0	0	0	0	0	<1000	<1000	<250	<250	<250	<250	0	0	
27-Aug-87	5	4	0	2	0	1	0	0	0	0	0	0	0	0	0	0	0	0	<1000	<1000	290	450	<250	<250	0	0	
03-Sep-87	3	2	0	2	0	4	0	0	0	0	0	0	0	0	0	0	0	0	<1000	<1000	2400	2000	1200	<250	0	0	
10-Sep-87	4	3	2	4	0	0	0	0	0	0	0	0	0	0	0	0	0	0	3000	<1000	5000	4400	4400	4400	0	0	
17-Sep-87	5	4	3	6	0	9	0	0	0	0	0	0	0	0	0	0	0	0	<1000	22400	2200	2700	4100	2100	0	0	
24-Sep-87																											
01-Oct-87	6	4	2	10	0	9	0	0	0	0	0	0	0	0	0	0	0	0	<1000	<1000	2100	<250	<250	<250	0	0	
08-Oct-87	10.3	5.1	2.1	10.6	0	8.9	0	0	0	0	0	0	0	0	0	0	0	0	<1000	<1000	2400	1900	2700	<250	0	0	
15-Oct-87	2.2	5	1.3	9.3	0	13.2	0	0	0	0	0	0	0	0	0	0	0	0	2500	<1000	2400	3300	3700	1300	0	0	
22-Oct-87	6	2	3	3	0	3	0	0	0	0	0	0	0	0	0	0	0	0	5200	<1000	6100	3200	56800	1200	0	0	
29-Oct-87																											
05-Nov-87	6	2	2	2	0	2	0	0	0	0	0	0	0	0	6	0	0	0	<1000	<1000	1200	1200	<250	<250	0	0	
12-Nov-87	10	7	3	9	1	8	0	0	0	0	0	0	0	2	0	0	0	0	5200	1200	3300	3700	3000	2000	0	0	
19-Nov-87	6	2	0	0	0	0	0	0	0	0	0	0	0	0	0	0	0	0	<1000	<1000	<250	2500	2800	<250	0	0	
26-Nov-87	16	7	9	13	4	11	0	0	0	0	0	0	0	9	3	0	0	0	<1000	2200	1600	2400	11300	5700	0	0	
03-Dec-87	8	7	4	9	2	4	0	0	0	0	0	0	0	36	8	0	0	0	<1000	2000	<250	1400	5800	3100	0	0	
10-Dec-87																											
17-Dec-87																											
24-Dec-87																											
31-Dec-87																											
07-Jan-88																											
14-Jan-88																											
21-Jan-88																											

all data reported in parts per billion (ppb)

AVERAGE	5.4	5.2	1.8	5.2	1.6	5.4	20.1	13.6	0.4	0.0	0.6	0.0	3.8	0.6	0.5	0.0	1.6	2.7	1866.7	2833.3	3465.8	3537.7	6516.7	1025.0	0.0	0.0
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TABLE II

CALENDAR YEAR 1987 SOLVENT MATERIAL BALANCE

MONTH 1987	FLOW MGM	FLOWS MGD	COMPOUND AVG. CONC. (ppb)	1,2 DICHLORO-	1,4 DICHLORO-	ETHYL	PERCHLORO-	TRICHLORO-	METHANOL	ACETONE	IPA	
				BENZENE	BENZENE	BENZENE	ETHYLENE	ETHANE				XYLENE
				13.6	0.0	0.0	0.6	0.0	2.7	2833.0	3538.0	1025.0
JAN	33.006	1.065		3.74	0.00	0.00	0.17	0.00	0.74	779.84	973.91	282.18
FEB	32.522	1.162		3.69	0.00	0.00	0.16	0.00	0.73	768.40	959.62	278.01
MAR	37.055	1.195		4.20	0.00	0.00	0.19	0.00	0.83	875.51	1097.38	316.76
APR	35.123	1.171		3.98	0.00	0.00	0.18	0.00	0.79	829.86	1036.37	300.25
MAY	38.45	1.241		4.36	0.00	0.00	0.19	0.00	0.87	908.47	1134.54	328.69
JUN	37.353	1.245		4.24	0.00	0.00	0.19	0.00	0.84	882.55	1102.17	319.31
JUL	39.967	1.289		4.53	0.00	0.00	0.20	0.00	0.90	944.31	1179.30	341.66
AUG	38.721	1.249		4.39	0.00	0.00	0.19	0.00	0.87	914.87	1142.54	331.01
SEP	35.326	1.211		4.12	0.00	0.00	0.18	0.00	0.82	858.28	1071.87	310.53
OCT	35.784	1.154		4.06	0.00	0.00	0.18	0.00	0.81	845.48	1055.88	305.90
NOV	33.817	1.127		3.84	0.00	0.00	0.17	0.00	0.76	799.00	997.84	289.08
DEC	34.698	1.119		3.94	0.00	0.00	0.17	0.00	0.78	819.82	1023.83	296.62
ANNUAL TOTALS	432,822	14,228		49.69	0.00	0.00	2.17	0.00	9.75	10226.38	12771.24	3699.98
TOTAL VOC (LBS)	26758.60											
TOTAL VOC (TONS)	13.38											

TABLE III

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

DATE	TOTAL WELL # 1	TOTAL WELL # 2	TOTAL # 1 & # 2	TOTAL WWTP	TOTAL GOV. SYS.
01-Jan-87	0	821700	845000	940500	0
02-Jan-87	0	828600	853300	901200	0
03-Jan-87	0	928600	950300	1004200	0
04-Jan-87	0	596500	1019800	1087800	0
05-Jan-87	0	1045700	1069700	1050000	0
06-Jan-87	0	1108000	1131600	1050000	0
07-Jan-87	0	1139600	1161700	1202300	0
08-Jan-87	0	1092900	1115800	1166500	0
09-Jan-87	0	1105800	1128500	1191100	0
10-Jan-87	0	1051600	1072800	1156300	0
11-Jan-87	0	978000	998200	1096100	0
12-Jan-87	0	926700	951500	981800	0
13-Jan-87	0	1061500	1085800	1119300	0
14-Jan-87	0	1120700	1139800	911300	0
15-Jan-87	0	1102200	1120200	1144600	0
16-Jan-87	0	1086400	1103900	1176400	0
17-Jan-87	0	1077800	1095500	1180700	0
18-Jan-87	0	1043000	1060800	1131100	0
19-Jan-87	0	1043900	1060300	1136800	0
20-Jan-87	0	1084800	1104200	1202100	0
21-Jan-87	0	1053400	1070900	1131800	0
22-Jan-87	0	1066800	1083200	1167300	0
23-Jan-87	0	1072400	1090300	1150400	0
24-Jan-87	0	1093300	1110300	1147600	0
25-Jan-87	0	492600	498800	544600	0
26-Jan-87	0	690300	694500	657700	0
27-Jan-87	0	864500	874600	907100	0
28-Jan-87	0	1015500	1035100	1000000	0
29-Jan-87	0	1164000	1184900	1000000	0
30-Jan-87	0	1143300	1162800	1205500	0
31-Jan-87	0	1206900	1227100	1264000	0
== Sum ==	0	31507000	32101200	33006100	0
== Average ==	0	1016354.84	1035522.58	1064712.9	0
== Min ==	0	492600	498800	544600	0
== Max ==	0	1206900	1227100	1264000	0

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

<u>DATE</u>	<u>TOTAL WELL # 1</u>	<u>TOTAL WELL # 2</u>	<u>TOTAL # 1 & # 2</u>	<u>TOTAL WWTP</u>	<u>TOTAL GOV. SYS.</u>
01-Feb-87	0	1316700	1339000	1360700	0
02-Feb-87	0	934800	951100	985500	0
03-Feb-87	0	923000	936900	963500	0
04-Feb-87	0	1078000	1096400	1164700	0
05-Feb-87	0	1172200	1192200	1274400	0
06-Feb-87	0	1058900	1078600	1154600	0
07-Feb-87	0	957200	973800	1057900	0
08-Feb-87	0	888800	908500	985900	0
09-Feb-87	0	782000	793100	871000	0
10-Feb-87	0	1019200	1037200	1090900	0
11-Feb-87	0	1153600	1173200	1210700	0
12-Feb-87	0	1182400	1201200	1242400	0
13-Feb-87	0	1152500	1170900	1209900	0
14-Feb-87	0	1169900	1190200	1237900	0
15-Feb-87	0	1034300	1052900	1101000	0
16-Feb-87	0	956600	376600	1059100	0
17-Feb-87	0	1121100	507600	1234200	0
18-Feb-87	0	1161100	486000	1253600	0
19-Feb-87	0	1138300	469800	1222400	0
20-Feb-87	0	1147700	385900	1218700	0
21-Feb-87	0	1134500	563200	1242600	0
22-Feb-87	0	1082400	365100	1183000	0
23-Feb-87	0	1003000	363700	1125000	0
24-Feb-87	0	1016800	428600	1100000	0
25-Feb-87	0	1087100	450900	1182600	0
26-Feb-87	0	1169300	515100	1256200	0
27-Feb-87	0	1151900	520800	1268700	0
28-Feb-87	0	1127200	507400	1265100	0
== Sum ==	0	30120500	22035900	32522200	0
== Average ==	0	1075732.14	786996.429	1161507.14	0
== Min ==	0	782000	363700	871000	0
== Max ==	0	1316700	1339000	1360700	0

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

<u>DATE</u>	<u>TOTAL WELL # 1</u>	<u>TOTAL WELL # 2</u>	<u>TOTAL # 1 & # 2</u>	<u>TOTAL WWTP</u>	<u>TOTAL GOV. SYS.</u>
01-Mar-87	0	977000	394100	1116100	0
02-Mar-87	0	1075800	449000	1174700	0
03-Mar-87	1085300	63300	25400	1230400	0
04-Mar-87	1116900	100	0	1215500	0
05-Mar-87	1078200	0	0	1229300	0
06-Mar-87	1156500	0	0	1235400	0
07-Mar-87	1159000	0	0	1253300	0
08-Mar-87	1052000	0	0	1187500	0
09-Mar-87	1016500	0	0	1146700	0
10-Mar-87	1124700	0	0	1268100	0
11-Mar-87	1108200	0	0	1220600	0
12-Mar-87	1121600	0	0	1220000	0
13-Mar-87	1168600	0	0	1262800	0
14-Mar-87	1121100	0	0	1179900	0
15-Mar-87	1008000	0	0	1118000	0
16-Mar-87	973100	0	0	1075500	0
17-Mar-87	1093800	0	0	1217900	0
18-Mar-87	1111000	0	0	1228100	0
19-Mar-87	1064500	0	0	1184700	0
20-Mar-87	1070300	0	0	1251400	0
21-Mar-87	1107500	0	0	1241500	0
22-Mar-87	934800	0	0	1051900	0
23-Mar-87	976000	0	0	1112800	0
24-Mar-87	1125400	0	0	1276800	0
25-Mar-87	1043200	0	0	1237000	0
26-Mar-87	1006400	0	0	1209300	0
27-Mar-87	1098500	0	0	1296400	0
28-Mar-87	984100	0	0	1160000	0
29-Mar-87	878300	0	0	1092000	0
30-Mar-87	1010100	0	0	1178300	0
31-Mar-87	1041100	0	0	1182500	0
== Sum ==	30834700	2116200	868500	37054400	0
== Average ==	994667.742	68264.5161	28016.129	1195303.23	0
== Min ==	0	0	0	1051900	0
== Max ==	1168600	1075800	449000	1296400	0

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

<u>DATE</u>	<u>TOTAL WELL # 1</u>	<u>TOTAL WELL # 2</u>	<u>TOTAL # 1 & # 2</u>	<u>TOTAL WWTP</u>	<u>TOTAL GOV. SYS.</u>
01-Apr-87	1080200	0	0	1194800	0
02-Apr-87	1124900	0	0	1229100	0
03-Apr-87	1144600	0	0	1288700	0
04-Apr-87	987600	0	0	1118400	0
05-Apr-87	755600	0	0	926500	0
06-Apr-87	936600	0	0	1029400	0
07-Apr-87	1115400	0	0	1227100	0
08-Apr-87	1171800	0	0	1266600	0
09-Apr-87	1066200	0	0	1208100	0
10-Apr-87	1106000	0	0	1273300	0
11-Apr-87	1043700	0	0	1204800	0
12-Apr-87	792200	0	0	967300	0
13-Apr-87	709100	0	0	935700	0
14-Apr-87	803400	0	0	1021200	0
15-Apr-87	1059400	0	0	1225500	0
16-Apr-87	1133400	0	0	1285900	0
17-Apr-87	1118600	0	0	1245300	0
18-Apr-87	1436800	0	0	1221400	0
19-Apr-87	682700	0	0	1150500	0
20-Apr-87	1005300	0	0	1535500	0
21-Apr-87	1113400	0	0	869100	0
22-Apr-87	1092700	0	0	1251000	0
23-Apr-87	1035400	0	0	1213100	0
24-Apr-87	680900	0	0	810800	0
25-Apr-87	1099100	0	0	1318100	0
26-Apr-87	882300	0	0	1126600	0
27-Apr-87	993100	0	0	1192700	0
28-Apr-87	1045600	0	686000	1229600	0
29-Apr-87	1115800	0	1139300	1306300	0
30-Apr-87	1056000	0	1079800	1250000	0
== Sum ==	=====	=====	=====	=====	=====
	30387800	0	2905100	35122400	0
== Average ==	=====	=====	=====	=====	=====
	1012926.67	0	96836.6667	1170746.67	0
== Min ==	=====	=====	=====	=====	=====
	680900	0	0	810800	0
== Max ==	=====	=====	=====	=====	=====
	1436800	0	1139300	1535500	0

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

DATE	TOTAL WELL # 1	TOTAL WELL # 2	TOTAL # 1 & # 2	TOTAL WWTP	TOTAL GOV. SYS.
01-May-87	1044800	0	1068000	1250000	0
02-May-87	1095800	0	1119500	1250000	15600
03-May-87	966200	0	989800	1200400	0
04-May-87	983100	0	1007800	1229600	5200
05-May-87	1113600	0	1136000	1332200	18500
06-May-87	1157000	0	1150800	1373400	9800
07-May-87	1024300	0	1079000	1269700	12800
08-May-87	1098500	0	1121700	1313700	12100
09-May-87	915700	0	935200	1120200	10900
10-May-87	1038100	0	1062700	1286000	2700
11-May-87	1049800	0	1071800	1277200	1100
12-May-87	1111300	0	1132900	1324500	14000
13-May-87	927300	280200	1224900	1335400	12500
14-May-87	936500	108600	1060600	1208200	6600
15-May-87	1086800	0	1110300	1288400	21700
16-May-87	1006700	0	1031700	1226900	9600
17-May-87	1084900	0	1110900	1323500	2600
18-May-87	973500	0	996000	1229700	3300
19-May-87	1098500	0	1122600	1340300	14800
20-May-87	1154600	0	1179000	1332700	21800
21-May-87	1090500	0	1114800	1280000	12400
22-May-87	1095200	0	1119500	1262000	10600
23-May-87	1059600	0	1083100	1208100	15800
24-May-87	976100	0	1000700	1150700	0
25-May-87	727700	0	746400	926000	0
26-May-87	939000	0	961300	1079900	2500
27-May-87	1068000	0	1090800	1250800	6500
28-May-87	1063500	0	1085600	1221600	13400
29-May-87	1086500	0	1106500	1255900	12800
30-May-87	989400	0	1016400	1162900	9000
31-May-87	954600	0	978200	1140200	0
== Sum ==	31917100	388800	33014500	38450100	278600
== Average ==	1029583.87	12541.9355	1064983.87	1240325.81	8987.09677
== Min ==	727700	0	746400	926000	0
== Max ==	1157000	280200	1224900	1373400	21800

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

DATE	TOTAL WELL # 1	TOTAL WELL # 2	TOTAL # 1 & # 2	TOTAL WWTP	TOTAL GOV. SYS.
01-Jun-87	955400	0	978300	1154900	5000
02-Jun-87	1300	1167100	1187500	1330800	11500
03-Jun-87	0	904300	919500	1075400	16000
04-Jun-87	0	1019300	1036600	1179100	24700
05-Jun-87	0	1164600	1183500	1287600	14100
06-Jun-87	0	1042300	1058600	1189300	19400
07-Jun-87	0	898800	915600	1043400	0
08-Jun-87	0	901100	916300	976700	12400
09-Jun-87	0	1152800	1172200	1195800	29200
10-Jun-87	0	1214900	1234500	1259400	20000
11-Jun-87	0	1236700	1256700	1316100	16100
12-Jun-87	0	1264100	1283900	1342400	19000
13-Jun-87	0	1240300	1260000	1308700	19700
14-Jun-87	0	1026200	1042200	1158500	0
15-Jun-87	0	1051000	1068100	1170100	8200
16-Jun-87	0	1177100	1196400	1309200	13200
17-Jun-87	0	1172700	1191800	1288000	12400
18-Jun-87	0	1223400	1243000	1379100	8900
19-Jun-87	0	1265500	1284200	1382700	19500
20-Jun-87	0	1162200	1180300	1300700	13600
21-Jun-87	0	1082500	1100200	1234700	9900
22-Jun-87	0	1090900	1108400	1227900	10000
23-Jun-87	0	1198900	1217400	1326100	23000
24-Jun-87	0	1196300	1214700	1295400	17300
25-Jun-87	0	1199300	1218900	1303600	12200
26-Jun-87	0	1209000	1227600	1333600	11700
27-Jun-87	0	1177600	1195800	1269600	13300
28-Jun-87	0	1072900	1089400	1173700	5800
29-Jun-87	0	1132300	1152400	1245800	4200
30-Jun-87	0	1186300	1203600	1294500	10500
== Sum ==	956700	32830400	34337600	37352800	400800
== Average ==	31890	1094346.67	1144586.67	1245093.33	13360
== Min ==	0	0	915600	976700	0
== Max ==	955400	1265500	1284200	1382700	29200

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

DATE	TOTAL WELL # 1	TOTAL WELL # 2	TOTAL # 1 & # 2	TOTAL WWTP	TOTAL GOV. SYS.
01-Jul-87	1700	1203000	1222700	1314400	11300
02-Jul-87	0	1217200	1237400	1333700	7800
03-Jul-87	0	1124700	1139200	1208300	11400
04-Jul-87	0	995900	1007500	1120000	0
05-Jul-87	0	978100	984200	1097900	0
06-Jul-87	0	1048200	1059100	551300	2400
07-Jul-87	0	1190700	1209200	1954900	6000
08-Jul-87	0	1308100	1327400	1407900	9300
09-Jul-87	0	1177700	1197900	1308800	9400
10-Jul-87	0	1236200	1255000	1340900	14700
11-Jul-87	0	1220700	1240200	1339300	11300
12-Jul-87	0	1064800	1082700	1220500	0
13-Jul-87	0	1156000	1176300	1282800	1500
14-Jul-87	0	1325500	1349700	1411300	6700
15-Jul-87	0	1327100	1348600	1379200	10700
16-Jul-87	0	1343800	1366700	1398400	8900
17-Jul-87	0	1302400	1324700	1367000	10700
18-Jul-87	0	1210000	1232000	1347000	10500
19-Jul-87	0	29919000	1331300	1425900	0
20-Jul-87	0	0	936700	972300	3700
21-Jul-87	0	0	1185000	1304500	7300
22-Jul-87	0	0	1169300	1294600	13700
23-Jul-87	0	0	1243900	1376900	12400
24-Jul-87	0	0	1191900	1363200	10000
25-Jul-87	0	0	1419100	1537100	16000
26-Jul-87	0	0	1031300	1197200	0
27-Jul-87	0	0	780800	923700	3500
28-Jul-87	0	0	1122800	1275700	4400
29-Jul-87	0	0	1118800	1254900	19200
30-Jul-87	0	0	1192500	1317500	12500
31-Jul-87	0	0	1213800	1339300	8600
== Sum ==	1700	51349100	36697700	39966400	243900
== Average ==	54.8387097	1656422.58	1183796.77	1289238.71	7867.74194
== Min ==	0	0	780800	551300	0
== Max ==	1700	29919000	1419100	1954900	19200

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

<u>DATE</u>	<u>TOTAL WELL # 1</u>	<u>TOTAL WELL # 2</u>	<u>TOTAL # 1 & # 2</u>	<u>TOTAL WWTP</u>	<u>TOTAL GOV. SYS.</u>
01-Aug-87	0	0	1194600	1301100	10400
02-Aug-87	0	0	1040700	1189600	0
03-Aug-87	0	0	1106500	1218300	10500
04-Aug-87	0	0	1239600	1373900	6800
05-Aug-87	0	0	1186600	1297900	10600
06-Aug-87	0	0	1175100	1305900	9200
07-Aug-87	0	0	1242200	1386200	7300
08-Aug-87	0	0	757200	888100	14800
09-Aug-87	0	0	773300	941800	0
10-Aug-87	0	0	1038000	1184800	900
11-Aug-87	0	0	1252200	1365700	3000
12-Aug-87	0	0	1247600	1330500	5200
13-Aug-87	0	0	1214000	1302600	9700
14-Aug-87	0	0	442600	1289700	0
15-Aug-87	0	0	0	1259200	15700
16-Aug-87	0	0	0	1180700	0
17-Aug-87	0	0	0	1199600	0
18-Aug-87	0	0	0	1291000	4300
19-Aug-87	0	0	0	1576500	12100
20-Aug-87	0	0	0	1170000	2000
21-Aug-87	0	0	0	1294000	9000
22-Aug-87	0	0	0	1180900	10800
23-Aug-87	3700	0	0	1006300	0
24-Aug-87	0	0	0	1104300	7100
25-Aug-87	1082200	0	0	1320400	4500
26-Aug-87	1152300	0	1103000	1349300	1800
27-Aug-87	1171600	0	1175700	1318300	8700
28-Aug-87	1030500	0	1195000	1374900	8500
29-Aug-87	1030500	0	1052400	1229100	3700
30-Aug-87	1112800	0	1136900	1337200	0
31-Aug-87	940200	0	964400	1152400	5200
== Sum ==	7523800	0	21537600	38720200	181800
== Average ==	242703.226	0	694761.29	1249038.71	5864.51613
== Min ==	0	0	0	888100	0
== Max ==	1171600	0	1252200	1576500	15700

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

DATE	TOTAL WELL # 1	TOTAL WELL # 2	TOTAL # 1 & # 2	TOTAL WWTP	TOTAL GOV. SYS.
01-Sep-87	1436000	0	1461900	1671800	5600
02-Sep-87	904000	0	922800	1039800	2500
03-Sep-87	1171700	0	1192900	1305300	7300
04-Sep-87	744500	0	758100	1432600	13800
05-Sep-87	600	0	300	1137700	2800
06-Sep-87	0	0	0	1054800	1400
07-Sep-87	0	0	0	724700	10000
08-Sep-87	0	0	0	843200	9600
09-Sep-87	0	0	0	1293200	4700
10-Sep-87	0	0	0	1229100	8100
11-Sep-87	0	0	0	1242400	9100
12-Sep-87	0	0	0	1272800	2500
13-Sep-87	0	0	0	1249300	1600
14-Sep-87	0	0	0	1185200	6500
15-Sep-87	0	0	0	1350600	4300
16-Sep-87	0	0	0	1317000	5200
17-Sep-87	0	0	0	1354800	5300
18-Sep-87	0	0	0	1373400	7300
19-Sep-87	0	0	0	1290000	4800
20-Sep-87	0	0	0	1136500	0
21-Sep-87	0	0	0	726500	0
22-Sep-87	0	0	0	1781100	12000
23-Sep-87	0	0	0	1304000	2300
24-Sep-87	0	0	0	1352000	4500
25-Sep-87	0	0	0	1371700	5100
26-Sep-87	0	0	0	1162500	5300
27-Sep-87	0	0	0	703600	0
28-Sep-87	0	0	0	961700	4000
29-Sep-87	0	0	0	1166900	2800
30-Sep-87	0	0	0	1292000	7900
== Sum ==	4256800	0	4336000	36326200	156300
== Average ==	141893.333	0	144533.333	1210873.33	5210
== Min ==	0	0	0	703600	0
== Max ==	1436000	0	1461900	1781100	13800

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

<u>DATE</u>	<u>TOTAL WELL # 1</u>	<u>TOTAL WELL # 2</u>	<u>TOTAL # 1 & # 2</u>	<u>TOTAL WWTP</u>	<u>TOTAL GOV. SYS.</u>
01-Oct-87	0	0	0	1202800	6200
02-Oct-87	0	0	0	1063600	6800
03-Oct-87	0	0	0	1308200	14700
04-Oct-87	0	0	0	954200	0
05-Oct-87	0	0	0	1149100	1600
06-Oct-87	0	0	0	1221600	7800
07-Oct-87	0	0	0	1196500	0
08-Oct-87	0	0	0	1219700	8700
09-Oct-87	0	0	0	1219700	5500
10-Oct-87	0	0	0	1215800	6200
11-Oct-87	0	0	0	1183500	400
12-Oct-87	0	0	0	1352800	7500
13-Oct-87	0	0	0	948100	3900
14-Oct-87	0	0	0	1222400	4400
15-Oct-87	0	0	0	1167000	6200
16-Oct-87	0	0	0	1266800	4200
17-Oct-87	0	0	0	1265500	10900
18-Oct-87	0	0	0	793500	200
19-Oct-87	0	0	0	1105900	0
20-Oct-87	0	0	0	1176500	12400
21-Oct-87	0	0	0	1197800	3300
22-Oct-87	0	0	0	1183000	9100
23-Oct-87	0	0	0	1175100	4800
24-Oct-87	0	0	0	1104100	10000
25-Oct-87	0	0	0	1093900	0
26-Oct-87	0	0	0	1067100	0
27-Oct-87	0	0	0	1095600	4700
28-Oct-87	0	0	0	1160300	5600
29-Oct-87	0	0	0	1150000	10700
30-Oct-87	0	0	0	1173500	8400
31-Oct-87	0	0	0	1149900	3900
== Sum ==	0	0	0	35783500	168100
== Average ==	0	0	0	1154306.45	5422.58065
== Min ==	0	0	0	793500	0
== Max ==	0	0	0	1352800	14700

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

DATE	TOTAL WELL # 1	TOTAL WELL # 2	TOTAL # 1 & # 2	TOTAL WWTF	TOTAL GOV. SYS.
01-Nov-87	0	0	0	1114300	2500
02-Nov-87	0	0	0	1125900	3000
03-Nov-87	1181700	0	1205800	1312900	6600
04-Nov-87	1155400	0	1175900	1252200	10000
05-Nov-87	1097300	0	1121000	1305400	7800
06-Nov-87	1083400	0	1106100	1271800	6600
07-Nov-87	1087200	0	1110900	1189800	7800
08-Nov-87	899100	0	919900	1014800	0
09-Nov-87	988700	0	1012500	1118900	200
10-Nov-87	1051600	0	1074800	1185900	4700
11-Nov-87	1194700	0	1217500	1331000	3800
12-Nov-87	1162400	0	1185900	1244800	4300
13-Nov-87	1121400	0	1143700	1190300	6100
14-Nov-87	1102600	0	1126100	1174700	7300
15-Nov-87	988100	0	1010200	1102300	0
16-Nov-87	876000	0	896300	986300	6900
17-Nov-87	1196600	0	1219400	1326300	5800
18-Nov-87	1231100	0	1252900	1007500	5000
19-Nov-87	994200	0	1014600	1482400	8100
20-Nov-87	1170400	0	1193100	1249300	12900
21-Nov-87	1059500	0	1082100	1151600	9500
22-Nov-87	1074700	0	1098300	1158500	0
23-Nov-87	965200	0	987100	1078200	4000
24-Nov-87	860000	0	877400	1005900	8500
25-Nov-87	1057900	0	1078000	1170000	6300
26-Nov-87	3141400	0	3204200	3218100	6700
27-Nov-87	0	0	0	0	0
28-Nov-87	0	0	0	0	0
29-Nov-87	0	0	0	0	0
30-Nov-87	930800	0	949800	1047400	9700
== Sum ==	28671400	0	29263500	33816500	154100
== Average ==	955713.333	0	975450	1127216.67	5136.66667
== Min ==	0	0	0	0	0
== Max ==	3141400	0	3204200	3218100	12900

HARRIS SEMICONDUCTOR
DEEPWELL INJECTION REPORT
DISCHARGE VOLUMES (GALLONS)

<u>DATE</u>	<u>TOTAL WELL # 1</u>	<u>TOTAL WELL # 2</u>	<u>TOTAL # 1 & # 2</u>	<u>TOTAL WWTP</u>	<u>TOTAL GOV. SYS.</u>
01-Dec-87	1193000	0	1217200	1285500	7699
02-Dec-87	1102900	0	1124700	1191700	4101
03-Dec-87	1125100	0	1148300	1213799	7700
04-Dec-87	1232800	0	1282000	1336100	8200
05-Dec-87	1127000	0	1149800	1224801	4300
06-Dec-87	1110900	0	1135500	1123500	0
07-Dec-87	1024500	0	1049100	1072800	2400
08-Dec-87	1102600	0	1126600	1228800	4400
09-Dec-87	1159900	0	1184300	1285100	4300
10-Dec-87	1104500	0	1129300	1249000	7200
11-Dec-87	1140600	0	1164800	1297100	4900
12-Dec-87	1105700	0	1128300	1200800	3500
13-Dec-87	1001100	0	1024500	1099400	0
14-Dec-87	1070800	0	1094700	1166000	4100
15-Dec-87	1093300	0	1126400	1266400	5800
16-Dec-87	1013100	0	1174900	1314000	2300
17-Dec-87	1083700	0	1357000	1233800	6600
18-Dec-87	1046600	0	1019600	1198000	2500
19-Dec-87	1077200	0	1051300	1269900	2700
20-Dec-87	1042600	0	1016200	1267000	0
21-Dec-87	988600	0	960200	1156900	7700
22-Dec-87	1111100	0	1088600	1309600	7800
23-Dec-87	1125800	0	1100000	1340400	6000
24-Dec-87	677300	0	659200	802600	5300
25-Dec-87	0	0	0	0	0
26-Dec-87	0	0	0	0	0
27-Dec-87	2276600	0	2284800	2917600	0
28-Dec-87	615300	0	587600	750700	0
29-Dec-87	521700	0	500800	663400	0
30-Dec-87	595500	0	565400	732700	0
31-Dec-87	395300	0	375700	500400	0
== Sum ==	=====	=====	=====	=====	=====
	30265100	0	30826800	34697800	109500
== Average ==	=====	=====	=====	=====	=====
	976293.548	0	994412.903	1119283.87	3532.25806
== Min ==	=====	=====	=====	=====	=====
	0	0	0	0	0
== Max ==	=====	=====	=====	=====	=====
	2276600	0	2284800	2917600	8200

*HARRIS SEMICONDUCTOR
CALENDAR YEAR 1987
VOC – MATERIAL BALANCE
ATTACHMENT 3
AIR EMISSIONS*

SOLVENT SCRUBBERS--HARRIS SEMICONDUCTOR

BLDG	SCRUBBER#	ACTUAL PRODUCTION SCHEDULE (hrs/yr)	TOTAL YEARLY VOC EMISSIONS (ton/yr)
04	F04S01	8760	0.26
04	F04S02	8760	min
04	F04S03	8760	1.93
04	F04S08	8760	8.77
51	F51S02	7488	10.04
51	F51S03	7488	3.28
51	F51S04	7488	1.51
51	F51S05	7488	14.51
54	F54S01	4160	8.70
54	F54S02	4160	8.70
54	F54S03	8760	32.59
54	F54S04	8760	32.59
57	F57S01	4160	0.95
58	F58S01	7488	2.49
58	F58S02	520	0.10
59	F59S03	5980	0.37
60	F60S01	4160	min
61	F61S01	1040	0.07
62	F62S02	2112	0.32
63	F63S02	7488	1.78
63	F63S03	4160	2.35

			131.29

* Above emission data includes offshift emissions.
 * When multiple testing was performed, values are indicative of highest VOC concentrations observed.

*HARRIS SEMICONDUCTOR
CALENDAR YEAR 1987
VOC - MATERIAL BALANCE
ATTACHMENT 4
CHEMICAL USAGE*

TABLE IV

CODE	CHEMICAL	TRADE NAME	NO COMPONENT	COMPONENT UNITS
S	1,1,1 TRIMETHYL-N-TRIMETHYL ETHER	HMDS	1234.320	0.000 P
S	1,1,1 TRIMETHYL-N-TRIMETHYL ETHER	HMDS 10%	37029.600	P
S	1,1,1 TRIMETHYL-N-TRIMETHYL ETHER	HMDS BTL	0.057	P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, WAYCOAT HPR 205		686.949 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY MICROPOSIT SAL 601-		2.819 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY THINNER A		1564.717 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, WAYCOAT HPR 204		4538.028 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY S1400-27		4140.777 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, HOECHST AZ 4903		5.594 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY S1400-17		2.992 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY S1400-21		22.898 P
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY ECX 1000		1.409 P
S	2-METHOXYETHANOL	PHOTORESIST, KTI NEG 747		95.621 P
S	2-PENTANONE	2-PENTANONE	303.993	P
S	ALIPHATIC PETROLEUM DISTILLATES	DEVELOPER, KTI PROJECTION		1749.398 P
S	ALIPHATIC SOLVENTS	FLUX, KENCO 934-SA		2.752 P
S	BUTYL ACETATE	BUTYL ACETATE	52181.712	P
S	BUTYL ACETATE	PHOTORESIST, WAYCOAT HPR 204		383.987 P
S	BUTYL ACETATE	PHOTORESIST, WAYCOAT HPR 205		58.126 P
S	CELLOSOLVE ACETATE	CELLOSOLVE ACETATE	6593.187	P
S	CELLOSOLVE ACETATE	HMDS 10%		32326.841 P
S	CELLOSOLVE ACETATE	PHOTORESIST, SHIPLEY 1400-27		2166.772 P
S	CELLOSOLVE ACETATE	PHOTORESIST, ULTRAMAC PR 914		8.090 P
S	CELLOSOLVE ACETATE	PHOTORESIST, SHIPLEY AZ 1370		271.817 P
S	CERIC AMMONIUM NITRATE	CERIC AMMONIUM NITRATE	273.000	P
S	CHF3	CHF3	70.000	P
S	CHLORDIFLUOROMETHANE	FREON 22	4875.000	P
S	CHLORINATED HYDROCARBONS	STRIPPER, HUNT MICROSTRIP		45711.540 P
S	CHLOROTRIFLUOROMETHANE	FREON 13		1.000 EA
S	DICHLORODIFLUOROMETHANE	MS 240		24.000 P
S	DICHLORODIFLUOROMETHANE	MS 230 CONTACT RE-NU		0.800 P
S	DICHLORODIFLUOROMETHANE	MS 136		17.850 P
S	DICHLORODIFLUOROMETHANE	MS 190HD		7.200 P
S	DICHLORODIFLUOROMETHANE	MS 180		28.800 P
S	DICHLORODIFLUOROMETHANE	MS 220 AERO-DUSTER		12.000 P
S	DICHLORODIFLUOROMETHANE	MS 190		7.200 P
S	EDTA	HACH TOTAL CHLORINE REAGENT		0.100 EA
S	EDTA	HACH FREE CHLORINE REAGENT		0.050 PK
S	ETHANOL	MARKEM INK FORM C		18.250 P
S	ETHANOL	THINNER, KESTER 4163		629.080 P
S	ETHYL ACETATE	MARKEM INK FORM F		18.250 P
S	ETHYL ALCOHOL	FLUX, KENCO 934-SA		2.174 P
S	ETHYL ALCOHOL	ETHYL ALCOHOL	683.561	P
S	ETHYL ALCOHOL	BLACO-TRON TMS PLUS		151.200 P
S	FC 40	FC 40	1800.000	P
S	FC 70	FC 70	240.000	P
S	FC 71	FC 71	15.000	P
S	FC 77	FC 77	462.000	P
S	FC 84	FC 84	3220.000	P
S	FREON 115	FREON 115	40.000	P
S	HMDS	HMDS 10%		2951.279 P
S	HMDS	HMDS	950.426	P
S	IPA	THINNER, KESTER 4163		743.458 P
S	IPA	FLUX, ALPHA 100		3.294 P
S	IPA	FLUX, KESTER 2163		378.844 P
S	ISOPROPYL ALCOHOL	FLUX, KESTER 135		38.873 P
S	ISOPROPYL ALCOHOL	ISOPROPYL ALCOHOL	63329.623	P
S	ISOPROPYL ALCOHOL	ETHYL ALCOHOL		34.178 P
S	ISOPROPYL ALCOHOL	FLUX, ALPHA 611	79.063	P

<u>CODE</u>	<u>CHEMICAL</u>	<u>TRADE NAME</u>	<u>NO COMPONENT</u>	<u>COMPONENT UNITS</u>
S	N-BUTYL	PHOTORESIST, SHIPLEY 1400-27		190.232 P
S	N-BUTYL	PHOTORESIST, SHIPLEY AZ 1370		17.514 P
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY S1400-21		2.055 P
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY ECX 1000		0.128 P
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY S1400-17		0.257 P
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY MICROPOSIT SAL 601-		0.257 P
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY S1400-27		339.071 P
S	N-BUTYL ACETATE	PHOTORESIST, HOECHST AZ 4903		0.550 P
S	N-BUTYL ACTATE	PHOTORESIST, SHIPLEY THINNER A		145.316 P
S	N-METHYL-2-PYRROLIDONE	STRIPPER, SHIPLEY 1165		1299.372 P
S	PGMEA	THINNER, HOECHST AZ 1500	308.980	P
S	PGMEA	PHOTORESIST, HOECHST AZ 5206		26.211 P
S	PGMEA	PHOTORESIST, HOECHST AZ 5214		200.789 P
S	SDA 30 ALCOHOL	FREGN TE		4.030 P
S	TELONER OF TETRAFLUOROETHANE	MS 136		0.765 P
S	TETRAFLUOROMETHANE	FREGN 14	140.000	P
S	TETRAFLUOROMETHANE	DE 100		637.560 CF
S	TETRAFLUOROMETHANE	FREGN 14	840.000	P
S	TETRAFLUOROMETHANE	FREGN 14	630.000	P
S	TRIFLOUROMETHANE	TRIFLOUROMETHANE		P
===== Sum =====			175799.523	101573.217

CHEMICALS USED PER P/R SYSTEM DURING 1987

code	CHEMICAL NAME	TRADE NAME	HSS	RECEIVED	ACTUAL LBS	SS FOR	FRGTO
		TRADE NAME	PART NO	AMOUNT	NO COMPONENTCOMPONENT	CHEMICAL	% %
S	1,1,1 TRIMETHYL-N-TRIMETHYL ETHER	HMDS	0	148 GL	1234.320	0.000 P	1 0 0
S	1,1,1 TRIMETHYL-N-TRIMETHYL ETHER	HMDS 10%		4440 GL	37029.600	P	1 0 0
S	1,1,1 TRIMETHYL-N-TRIMETHYL ETHER	HMDS BTL		21.5 KG	0.057	P	0 0 0
S	2,2 DIBROMO 3 NITRILOPROPIO	NALCO 2510		660 GL	5504.400	P	1 0 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY THINNER A		220 GL	1564.717 P	1.04 56	82 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY S1400-27		770 GL	4140.777 P	1.04 56	62 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY S1400-17		0.5 GL	2.992 P	1.04 56	69 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, WAYCOAT HPR 204		372 GL	4538.928 P	1.04 56	60 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY MICROPOSIT SAL 501-ER7		0.5 GL	2.819 P	1.04 56	65 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, HOECHST AZ 1903		1.5 GL	5.594 P	1.04 56	43 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, WAYCOAT HPR 205		132 GL	586.149 P	1.04 56	60 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY S1400-21		4 GL	22.398 P	1.04 56	66 0
S	2-ETHOXYETHYL ACETATE	PHOTORESIST, SHIPLEY ECK 1000		0.25 GL	1.409 P	1.04 56	65 0
S	2-METHOXYETHANOL	PHOTORESIST, KTI NEG 747		197 GL	95.621 P	0.97 56	6 0
S	2-PENTANONE	2-PENTANONE	210549	45 EA	303.993	P	0.81
S	ABRASIVES	Z-100		300 P	228.000	P	76 0
S	ACETIC ACID	ACETIC ACID	210062-01	8010 P	8010.000	P	1.05
S	ALIPHATIC PETROLEUM DISTILLATES	DEVELOPER, KTI PROJECTION		276 GL	1749.398 P	0.76 56	100 0
S	ALIPHATIC SOLVENTS	FLUX, KENCO 934-SA		1 GL	2.752 P	1	33 0
S	ALKALINE HYPOCHLORITE	Z-100		300 P	12.000 P		4 0
S	ALKYL ARYL SULFONIC ACID	STRIPPER, HUNT MICROSTRIP		9135 GL	17522.757 P	1	23 0
S	ANDE	NALCO 2510		660 GL	1651.320 P	1	20 40
S	AMMONIUM FLUORIDE	AMMONIUM FLUORIDE	210062-01	41796 P	41796.000	P	1.32
S	AMMONIUM FLUORIDE	ETCH, BUFFERED OXIDE ETCH 9:1		1464 GL	14505.195 P	1.32	90 0
S	AMMONIUM HYDROXIDE	ETCH, EDTA		68 KG	0.057	P	0.89 0 0
S	AMMONIUM HYDROXIDE	AMMONIUM HYDROXIDE	210062-04	1965 L	375.303	P	0.89
S	AMMONIUM PERSULFATE	STRIPPER, BURMAR SA 80		2080 P	2080.000	P	1.98 0 0
S	ANIT STATIC SPRAY AMERICAN SCI	ANIT STATIC SPRAY AMERICAN SCI	210577	22 GL	183.480	P	1
S	ARCOSOLV PM	ARCOSOLV PM	210062-12	9 GL	64.718	P	0.97
S	ARGON	ARGON	210269-00	35 CY			
S	ARGON	ARGON	210269	8614 CF			
S	BORON TRIBROMIDE	BORON TRIBROMIDE	210023	38.4 KG	84.657	P	2.65
S	BORON TRICHLORIDE	BORON TRICHLORIDE	210637	3 CY			1.35
S	BORON TRICHLORIDE	BORON TRICHLORIDE	210637-00	3 CY	42.000	P	1.35
S	BORON TRIFLUORIDE	BORON TRIFLUORIDE	210216	3.12 KG	5.878	P	3.07
S	BORON TRIFLUORIDE	BORON TRIFLUORIDE	210216-00	41 CY	7.231	P	3.07
S	BUTYL ACETATE	BUTYL ACETATE	210062-03	7110 GL	52181.712	P	0.88
S	BUTYL ACETATE	PHOTORESIST, WAYCOAT HPR 205		132 GL	58.126 P	0.88	6 0
S	BUTYL ACETATE	PHOTORESIST, WAYCOAT HPR 204		872 GL	383.987 P	0.88	6 0
S	CALCIUM CARBONATE	COOL AMP		4 P	1.400 P	0	35 45
S	CARBON DIOXIDE	CARBON DIOXIDE	215574-00	254 CY	19110.000	P	1.56
S	CELLOSOLVE ACETATE	PHOTORESIST, SHIPLEY AZ 1370		48 GL	271.817 P	0.97	70 0
S	CELLOSOLVE ACETATE	PHOTORESIST, SHIPLEY 1400-27		432 GL	2156.772 P	0.97	62 0
S	CELLOSOLVE ACETATE	HMDS 10%		4440 GL	32326.341 P	0.97	90 0
S	CELLOSOLVE ACETATE	PHOTORESIST, ULTRAMAC PR 914		2 GL	8.690 P	0.97	50 0
S	CELLOSOLVE ACETATE	CELLOSOLVE ACETATE	210062-05	815 GL	6593.187	P	0.97
S	CERIC AMMONIUM NITRATE	CERIC AMMONIUM NITRATE	210062-03	273 P	273.000	P	
S	CERIC SULFATE	CERIC SULFATE	210062-02	63 KG	178.870	P	
S	CHF3	CHF3	210575-00	70 P	70.000	P	
S	CHLOROFLUOROMETHANE	FREDON 22	215283-00	4875 P	4875.000	P	
S	CHLORINATED HYDROCARBONS	STRIPPER, HUNT MICROSTRIP		9135 GL	45711.540 P	1	68 0
S	CHLOROTRIFLUOROMETHANE	FREDON 13		1 EA	1.000 EA	0	0 100
S	COMPRESSED AIR	COMPRESSED AIR	215577-00	1 CY			
S	CYCLIFIED POLYISOPRENE	PHOTORESIST, KTI NEG 747		197 GL	71.470 P	0.97 56	5 15

CHEMICALS USED PER P/R SYSTEM DURING 1987

	DEVELOPER, SHIPLEY 1350	DEVELOPER, SHIPLEY 1350	210111-00	1150 GL	9591.000	P	1		
	DEVELOPER, SHIPLEY 318	DEVELOPER, SHIPLEY 318	210111-02	3416 GL	0.000	P	1		
S	DICHLORODIFLUOROMETHANE	MS 190		144 P			28.800 P	1.57 56	0 20
S	DICHLORODIFLUOROMETHANE	MS 136		51 P			17.250 P	1.57 56	35 40
S	DICHLORODIFLUOROMETHANE	MS 190		36 P			7.200 P	1.57 56	0 20
S	DICHLORODIFLUOROMETHANE	MS 190HD		36 P			7.200 P	1.57 56	0 20
S	DICHLORODIFLUOROMETHANE	MS 240		24 P			24.000 P	1.57 56	0 100
S	DICHLORODIFLUOROMETHANE	MS 220 AERO-DUSTER		12 P			12.000 P	1.57 56	100 0
S	DICHLORODIFLUOROMETHANE	MS 230 CONTACT RE-NU		4 P			0.900 P	1.57 56	20 0
	DICHLOROSILANE	DICHLOROSILANE	210367-00	540 CY					
	DICHLOROSILANE	DICHLOROSILANE	210367	990 P	990.000	P			
	DIMETHYL FORMAMIDE	BURMAR EK34		24 P	24.000	P		0	0 0
	DODECYLBENZENE SULFONIC ACID	STRIPPER, BURMAR 7120		12740 GL			26562.000 P	1	25 0
	DPD SALT	HACH TOTAL CHLORINE REAGENT		2 EA			0.100 EA	2.49 56	0 5
	DPD SALT	HACH FREE CHLORINE REAGENT		1 PK			0.050 PK	2.36 56	0 5
S	EDTA	HACH TOTAL CHLORINE REAGENT		2 EA			0.100 EA	2.49 56	0 5
S	EDTA	HACH FREE CHLORINE REAGENT		1 PK			0.050 PK	2.36 56	0 5
S	ETHANOL	MARKEM INK FORM C		36.5 P			18.250 P	0.79 56	30 70
S	ETHANOL	THINNER, KESTER 4163		217 GL			629.080 P	0.79 56	44 0
	ETHANOLAMINE	ETHANOLAMINE	210062-12	2 GL	16.680	P		1	
S	ETHYL ACETATE	MARKEM INK FORM F		36.5 P			18.250 P	0	30 70
S	ETHYL ALCOHOL	ETHYL ALCOHOL	210062-04	4032 L	683.561	P		0.79	
S	ETHYL ALCOHOL	FLUX, KENCO 934-SA		1 GL			2.174 P	0.79	33 0
S	ETHYL ALCOHOL	BLACO-TRON TMS PLUS		3780 P			151.200 P	1.46 56	4 0
	FATTY ACIDS	FLUX, KENCO 934-SA		1 GL			2.752 P	1	33 0
S	FC 40	FC 40	210062-05	1800 P	1800.000	P		1.9	
S	FC 70	FC 70	210062-11	240 P	240.000	P		1.9	
S	FC 71	FC 71	210062-08	15 P	15.000	P		1.9	
S	FC 77	FC 77	210062-00	462 P	462.000	P		1.8	
S	FC 84	FC 84	210062-12	3220 P	3220.000	P		1.7	
	FLUX, ALPHA 250 HF	FLUX, ALPHA 250 HF	210062-07	24 GL	200.160	P		1	
	FORMING GAS 10%	FORMING GAS 10%	210203	28600 CF	1879.252	P		0.39	
	FORMING GAS 5%	FORMING GAS 5%	210630-00	9 CY	117.798	P			
S	FREON 115	FREON 115	210635	2 CY	40.000	P			
	GREASE, SILICON, HIGH	GREASE, SILICON, HIGH	215454-00	53 TW	53.000	TW			
	GUM RESIN	FLUX, ALPHA 611		12 GL	30.024	P		0.3 56	0 0
	HELIUM	HELIUM	215574-00	33 CY					
	HELIUM	HELIUM	215574-00	118 CY					
	HELIUM	HELIUM	210636-00	2 CY					
S	HMDS	HMDS 10%		4440 GL			2851.279 P	0.77	10 0
S	HMDS	HMDS	210062-02	148 GL	950.426	P		0.77	
	HYDROGEN	HYDROGEN	210144-00	14040 CF					
	HYDROGEN PEROXIDE	HYDROGEN PEROXIDE	210062-00	14364 GL	140754.912	P		1.2	
S	IPA	THINNER, KESTER 4163		217 GL			743.458 P	0.79 56	52 0
S	IPA	FLUX, ALPHA 100		1 GL			3.294 P	0.79 56	50 75
S	IPA	FLUX, KESTER 2163		125 GL			378.845 P	0.79 56	46 0
	ISOPARAFFINIC HYDROCARBONS	DEVELOPER, WAYCOAT NEGATIVE		7546 GL	47825.730	P		0.75 56	0 0
	ISOPHORBONE	MARKEM INK FORM G		36.5 P			18.250 P	0.92 56	30 70
S	ISOPROPYL ALCOHOL	FLUX, KESTER 135		10 GL			38.873 P	0.79	59 0
S	ISOPROPYL ALCOHOL	ISOPROPYL ALCOHOL	210062-01	9612 GL	63729.623	P		0.79	
S	ISOPROPYL ALCOHOL	FLUX, ALPHA 611		12 GL	99.063	P		0.79 56	0 0
S	ISOPROPYL ALCOHOL	ETHYL ALCOHOL		4032 L			34.178 P	0.79	5 0
	JANUS GREEN B	JANUS GREEN B	210062-06	0.036 KG	0.057	P			
	LANTHANUM CHLORIDE	LANTHANUM CHLORIDE	210062-12	130 P	120.000	P			
	MARKEM 320	MARKEM 320	210205-00	100 GL	700.560	P		0.34	
	MARKEM 500	MARKEM 500	210205-01	28 GL	217.174	P		0.33	

CHEMICALS USED PER P/R SYSTEM DURING 1987

	MONOETHANOLAMINE	MARKEM 535	84	5L	35.729	P	1.02	56	5	15
	NEUTRACIT	NEUTRACIT	215216-00	3	EA					
	NEUTRASOL	NEUTRASOL	215216-00	5	BT					
	NITROGEN	NITROGEN	215571-00	1	CY					
	NITROGEN	NITROGEN	215577-00	3	CY					
	NITROGEN	NITROGEN	210328	19758	CF					
	NITROGEN	NITROGEN	210328-00	37402	CF					
	NITROGEN TRIFLUORIDE	NITROGEN TRIFLUORIDE	210640-00	1	CY				0.19	P/CF
	NITROGEN TRIFLUORIDE	NITROGEN TRIFLUORIDE	210640-00	1	CY				0.19	P/CF
	NITROMETHANE	BLACO-TROM TMS PLUS		3780	P	20.790	P	1.46	56	0 0.5
	NITROUS OXIDE	NITROUS OXIDE	210431-00	54	CY				1.23	
	NITROUS OXIDE	NITROUS OXIDE	210431	520	P	520.000	P	1.23		
S	N-BUTYL	PHOTORESIST, SHIPLEY AZ 1370		48	GL	17.614	P	0.88	5	0
S	N-BUTYL	PHOTORESIST, SHIPLEY 1400-27		432	GL	190.232	P	0.88	5	0
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY S1400-21		4	GL	2.055	P	0.88	7	0
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY ECI 1000		0.25	GL	0.128	P	0.88	56	7 0
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY MICROPOSIT SAL 801-ER7		0.5	GL	0.257	P	0.88	56	7 0
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY S1400-17		0.5	GL	0.257	P	0.88	56	7 0
S	N-BUTYL ACETATE	PHOTORESIST, HOECHST AZ 4903		1.5	GL	0.550	P	0.88	56	5 0
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY S1400-27		770	GL	339.071	P	0.88	56	6 0
S	N-BUTYL ACETATE	PHOTORESIST, SHIPLEY THINNER A		220	GL	145.316	P	0.88	56	7 0
S	N-METHYL-2-PYRROLIDONE	STRIPPER, SHIPLEY 1165		164	GL	1299.372	P	1	55	0
	OIL, AQUA #590	OIL, AQUA #590	210062-06	3	GL	25.020	P	1		
	OIL, HOLLIS #600	OIL, HOLLIS #600	210062-08	345	GL	2877.300	P	1		
	OIL, HYDRAULIC ANDAW68	OIL, HYDRAULIC ANDAW68	215362-00	385	GL	3210.900	P	1		
	OIL, MOBIL DTE LIGHT	OIL, MOBIL DTE LIGHT	215477-00	220	GL	1596.276	P	0.87		
	ORGANIC SALTS	FLUX, KENDO 934-SA		1	GL	8.340	P	1	0	0
	OXIYLPHENOL POLYETHOXYLATE	TRITON X-100		90	P	4.590	P	0	5	0
	OXYGEN	OXYGEN	210322-00	37164	CF			1.14		
	OXYGEN	OXYGEN	210322	5904	CF			1.14		
	OXYGEN	DE 100		593	CF	55.440	CF	1.14	8	0
	PALLADIUM CHLORIDE	RTM SOLUTION B		2	GL	0.157	P	1	1	0
	PDE 100	PDE 100	210321-00	21	CY					
	PDE 100	PDE 100	210321-00	915	CF					
S	PGMEA	PHOTORESIST, HOECHST AZ 5214		34	GL	280.789	P	0.97	56	73 0
S	PGMEA	PHOTORESIST, HOECHST AZ 5206		4	GL	26.211	P	0.97	56	81 0
S	PGMEA	THINNER, HOECHST AZ 1500		180	GL	808.980	P	0.97	56	0 0
	PHOSPHATE	DEVELOPER, SHIPLEY MICROPOSIT		1341	GL	11743.137	P	1.05	56	0 0
	PHOSPHINE 100%	PHOSPHINE 100%	210175-00	2	P	2.000	P			
	PHOSPHINE 15%	PHOSPHINE 15%	210215-00	108	CY	2504.777	P			
	PHOSPHINE 15%	PHOSPHINE 15%	210215	119	CF	2870.081	P			
	PHOSPHINE 1%	PHOSPHINE 1%	210175-00	4080	CF	296.153	P			
	PHOSPHINE 1%	PHOSPHINE 1%	210175-00	22	CY	383.256	P			
	PHOSPHOROUS OXYCHLORIDE	PHOSPHOROUS OXYCHLORIDE	210163	49.5	KG	109.128	P	1.58		
	PHOSPHOROUS TRIBROMIDE	PHOSPHOROUS TRIBROMIDE	210448	3.25	KG	7.165	P	2.85		
	POTASSIUM HYDROXIDE	Z-100		300	P	30.000	P	1.46	10	0
	POTASSIUM HYDROXIDE	QAB-D-SPERSE SC-2010		1980	GL	241.093	P	1.46	0	1
	POTASSIUM HYDROXIDE	POTASSIUM HYDROXIDE	210062-03	3140	GL	38233.096	P	1.46		
	POTASSIUM HYDROXIDE	DEVELOPER, HOECHST AZ 421K		13	GL	1.583	P	1.46	56	1 0
	POTASSIUM HYDROXIDE, PELLETS	POTASSIUM HYDROXIDE, PELLETS	210062-02	1400	KG	3036.440	P	2.04		
	POTASSIUM IODATE	NACH TOTAL CHLORINE REAGENT		2	EA	0.600	EA	2.49	56	0 20
	POTASSIUM PHOSPHATE	NACH TOTAL CHLORINE REAGENT		2	EA	1.000	EA	2.49	56	0 50
	POTASSIUM PHOSPHATE	NACH FREE CHLORINE REAGENT		1	PK	0.700	PK	2.36	56	0 70
	PROPRIETARY SUBSTITUTED HETEROCYCLEPHOTORESIST, SHIPLEY MICROPOSIT SAL 801-ER7			0.5	GL	0.714	P	0.8	56	1.9 0
	P-TOLUENE SULFONIC ACID	STRIPPER, SHIPLEY 140		1368	GL	1255.903	P	1.1	56	10 0
	RESIN	PHOTORESIST, ULTRAMAC PR 914		2	GL	5.604	P	1	30	0

CHEMICALS USED PER P/R SYSTEM DURING 1987

	RESIN	FLUX, KESTER 135		10 GL		34.194 P	1	41	0
	RUST-LICK 6-1066-D	RUST-LICK 6-1066-D	210062-05	22550 GL	188067.000		P	1	
S	50A 30 ALCOHOL	FREDM TE		8 GL		4.030 P	1.51	56	4 0
	SILANAMINE	HMDS 10X		4440 GL	27029.500		P	1	0 0
	SILANAMINE	HMDS		148 GL	1234.320		P	1	0 0
	SILANAMINE	HMDS BTL		21.6 KG	0.057		P	0	0 0
	SILANE 100Z	SILANE 100Z	210177	101.25 KG	223.216		P		
	SILANE 2Z	SILANE 2Z	210164-00	9 CY					
	SILANE 4Z	SILANE 4Z	210164-00	22980 CF	1688.553		P		
	SILICON DIOXIDE	CAB-O-SPERSE SC-1		4455 GL		13375.692 P	1.2	56	39 0
	SILICON DIOXIDE	CAB-O-SPERSE SC-3010		1980 GL		1753.950 P	1	30	0
	SILICON TETRACHLORIDE	SILICON TETRACHLORIDE	210082	7600 P	7800.000		P		
	SODIUM CHLORIDE	COOL AMP		4 P		1.500 P	2.15	40	50
	SODIUM CITRATE	HACH SODIUM CITRATE REAGENT		3 GL		3.782 P	1.17	56	30 0
	SODIUM HYPOPHSPHITE	RIM SOLUTION C		2 GL		0.000 P	0	15	0
	SODIUM METABISULFITE	HACH AMINO ACID SOLUTION		2 GL		1.785 P	1.07	56	10 0
	SODIUM MOLYBDATE	HACH MOLYBDATE 3 REAGENT		3 GL		6.465 P	1.28	55	20 0
	SODIUM PHOSPHATE	HACH TOTAL CHLORINE REAGENT		2 EA		0.500 EA	2.49	56	9 30
	SODIUM PHOSPHATE	HACH FREE CHLORINE REAGENT		1 PK		0.400 PK	2.36	56	40 0
	SODIUM SULFITE	HACH AMINO ACID SOLUTION		2 GL		0.892 P	1.07	56	5 0
	STANNOUS SULFATE	STANNOUS SULFATE	210062-03	36 KG	79.366		P	3.95	
	SULFUR HEXAFLUORIDE	SULFUR HEXAFLUORIDE	210582	1280 P	1380.000		P	0.38	P/CF
	SYLOID 244 X1661	SYLOID 244 X1661	210251	7170 P	7170.000		P		
	SYLOID 244 X1662	SYLOID 244 X1662	210251-00	3240 P	3240.000		P		
S	TELOMER OF TETRAFLUOROETHANE	MS 136		51 P		0.765 P	1	1	2
S	TETRAFLUOROMETHANE	DE 100		693 CF		637.560 CF	1	92	0
S	TETRAFLUOROMETHANE	FREDM 14	210307-00	9 CY	630.000		P		
S	TETRAFLUOROMETHANE	FREDM 14	210307-00	340 P	340.000		P		
S	TETRAFLUOROMETHANE	FREDM 14	210307	140 P	140.000		P		
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, HOECHST AZ 327 NIF		104 GL		76.728 P	1	56	5 0
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, SHIPLEY XP6043 CD 25.8		4 GL		0.567 P	1	56	2 0
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, SHIPLEY MF 320		76 GL	633.940		P	1	56 0 0
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, HOECHST AZ 440 NIF		128 GL		42.701 P	1	56	4 0
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, SHIPLEY MF 319		460 GL		76.728 P	1	56	2 0
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, SHIPLEY MF 314		1448 GL		362.290 P	1	56	3 0
	TETRAMETHYL AMMONIUM HYDROXIDE	DEVELOPER, WAYCOAT HPRD 402		1168 GL		292.234 P	1	56	3 0
	TIN ANODE ALPHA METAL	TIN ANODE ALPHA METAL	210193-00	24 EA					
	TRIBUTYL PHOSPHATE	MARKEM INK FORM J		36.5 P		18.250 P	0.98	56	30 70
	TRICHLOROSILANE	TRICHLOROSILANE	210239	161320 P	161320.000		P	1.22	
S	TRIFLUOROMETHANE	TRIFLUOROMETHANE	210591	72 CY					
	UNDOPED SPIN-ON	UNDOPED SPIN-ON	210621	30 EA					
	V M & P NAPTHA	BURMAR EX34		24 P	24.000		P	0	0 0

TABLE V

<u>JULY REPORT CHEMICAL</u>	<u>TRADE CHEMICAL</u>	<u>REC AMT</u>	<u>COMPONENT AMT</u>	<u>CODE</u>
1,1,1 TRICHLOROETHANE	TCA BUBBLERS	13	22.178276	S
1,1,1 TRICHLOROETHANE	MS 136	51	9.69	S
1,1,1 TRICHLOROETHANE	TCA BUBBLERS/APACHE	11.2	24.69152	S
1,1,1 TRICHLOROETHANE	1,1,1 TRICHLOROETHANE	10098	10098	S
1,1,1 TRICHLOROETHANE	1,1,1 TRICHLOROETHANE	6024	72094.6296	S
1,1,1 TRICHLOROETHANE	CLEANER, ALPHA 565	11	118.48221	S
1,1,1 TRICHLOROETHANE	BURMAR EK34	24	24	S
-- Sum			82391.67161	
1,2,4 TRICHLOROBENZENE	STRIPPER, BURMAR 712D	12740	69329.169	S
-- Sum			69329.169	
ACETONE	ACETONE	37684	248284.8024	S
ACETONE	FREON TA 55	110	22	S
-- Sum			248306.8024	
AROMATIC PHENOL	STRIPPER, BURMAR 712D	12740	22633.71583	S
-- Sum			22633.71583	
BUTYL ALCOHOL	BUTYL ALCOHOL	8	52.0416	S
-- Sum			52.0416	
CARBON TETRACHLORIDE	CARBON TETRACHLORIDE	48	20.163744	S
-- Sum			20.163744	
CRESOL	MARKEM INK FORM D	36.5	18.25	S
CRESOL	STRIPPER, HUNT MICROSTRIP	9135	13292.66188	S
-- Sum			13310.91188	
DIMETHYL PHTHALATE	MARKEM INK FORM E	36.5	36.5	S
-- Sum			36.5	
ETHYLBENZENE	PHOTORESIST, WAYCOAT HNR 999	35	25.3953	S
ETHYLBENZENE	PHOTORESIST, WAYCOAT HR 200	1774	1415.896812	S
ETHYLBENZENE	PHOTORESIST, WAYCOAT HR 100	708	513.71064	S
ETHYLBENZENE	PHOTORESIST, WAYCOAT SC 100	176	127.70208	S
ETHYLBENZENE	PHOTORESIST, WAYCOAT NEG VHR 3	298	281.089692	S
-- Sum			2363.794524	
ETHYLENE GLYCOL MONOETHYL ACET	MARKEM INK FORM H	36.5	18.25	S
ETHYLENE GLYCOL MONOETHYL ACET	MARKEM INK FORM I	36.5	18.25	S
-- Sum			36.5	
METHANOL	METHANOL	11016	72580.0176	S
-- Sum			72580.0176	
METHYL ALCOHOL	FREON TMS 650	3780	226.8	S
METHYL ALCOHOL	FREON TMS	8780	965.8	S
METHYL ALCOHOL	ETHYL ALCOHOL	4032	42.0775488	S
-- Sum			1234.677549	
METHYLENE CHLORIDE	FREON TMC 55	189	102.06	S
METHYLENE CHLORIDE	MS 190	72	28.8	S
-- Sum			130.86	
TRICHLOROTRIFLUOROETHANE	MS 180	144	115.2	S
TRICHLOROTRIFLUOROETHANE	FREON TMC 55	189	86.94	S
TRICHLOROTRIFLUOROETHANE	FREON TA 55	110	66	S
TRICHLOROTRIFLUOROETHANE	FREON TMS 650	3780	3553.2	S

<u>JULY REPORT CHEMICAL</u>	<u>TRADE CHEMICAL</u>	<u>REC AMT</u>	<u>COMPONENT AMT</u>	<u>CODE</u>
TRICHLOROTRIFLUOROETHANE	FREON TE	8	100.560384	S
TRICHLOROTRIFLUOROETHANE	FREON TMS	8780	7814.2	S
TRICHLOROTRIFLUOROETHANE	FREON TF	73830	73830	S
TRICHLOROTRIFLUOROETHANE	MS 136	51	1.785	S
TRICHLOROTRIFLUOROETHANE	MS 230 CONTACT RE-NU	22	17.6	S
TRICHLOROTRIFLUOROETHANE	MS 190	72	29.088	S
TRICHLOROTRIFLUOROETHANE	ACIDITY TEST KIT - PFPE	25	22.7	S
-- Sum -----			85637.27338	
XYLENE	MARKEM INK FORM B	36.5	36.5	S
XYLENE	PHOTORESIST, HOECHST AZ 4903	1.5	0.430344	S
XYLENE	PHOTORESIST, WAYCOAT SC 100	176	908.886528	S
XYLENE	PHOTORESIST, KTI NEG 747	747	4607.693208	S
XYLENE	PHOTORESIST, WAYCOAT HPR 205	132	37.870272	S
XYLENE	PHOTORESIST, SHIPLEY AZ 1370	48	17.21376	S
XYLENE	PHOTORESIST, WAYCOAT HNR 999	35	223.42026	S
XYLENE	PHOTORESIST, SHIPLEY ECX 1000	0.25	0.125517	S
XYLENE	PHOTORESIST, WAYCOAT HR 200	1774	9924.593328	S
XYLENE	PHOTORESIST, SHIPLEY MICROPOSI	0.25	0.125517	S
XYLENE	PHOTORESIST, ULTRAMAC PR 914	2	0.71724	S
XYLENE	PHOTORESIST, SHIPLEY S1400-17	0.5	0.251034	S
XYLENE	PHOTORESIST, WAYCOAT HPR 204	872	250.173312	S
XYLENE	PHOTORESIST, SHIPLEY S1400-21	4	2.008272	S
XYLENE	PHOTORESIST, WAYCOAT HR 100	708	4417.911504	S
XYLENE	PHOTORESIST, SHIPLEY S1400-27	764	328.782816	S
XYLENE	PHOTORESIST, WAYCOAT NEG VHR 3	298	1581.657648	S
XYLENE	PHOTORESIST, SHIPLEY THINNER A	220	142.01352	S
XYLENE	XYLENE	8208	58871.0592	S
-- Sum -----			81351.43328	
== Sum =====			679415.5324	

JULY 1988 REPORTABLE CHEMICALS IN TOTAL POUNDS

S	X	METHYL ALCOHOL	FREON TMS 650	0.79	856218	1.52	96	6	0	3780	P	226.8	P
S	X	METHYLENE CHLORIDE	FREON TMC 55	1.34	856216	0		54	0	189	P	102.06	P
S	X	METHYLENE CHLORIDE	MS 190	1.34	856886	0		40	0	72	P	28.8	P
	NL	NICKEL	NICKEL POWDER	9.9						2	EA	2	EA
	Y	NICKEL CHLORIDE	NICKEL PLATING SOLUTION			0		1	0	5	EA	0.05	EA
	Y	NICKEL SULFATE	NICKEL B		857093	1.1	96	1	0	8	GL	0.98	GL
	Y	NICKEL SULPHATE	NICKEL PLATING SOLUTION			0		60	0	5	EA	3	EA
	X	NITRIC ACID	DS-9-314	1.42	856161	1.19	96	5	0	1	P	0.05	P
		NITRIC ACID	NITRIC ACID	1.42						72534	P	72534.00	P
	X	NITRIC ACID	STRIPPER, ALLIED RT 2	1.42	856394	0		5	0	10044	P	502.2	P
	X	PHOSPHORIC ACID	DS-9-314	1.69	856161	1.19	96	25	0	1	P	0.25	P
		PHOSPHORIC ACID	PHOSPHORIC ACID	1.69						43848	P	43848.00	P
	Y	SILVER CHLORIDE	COOL AMP		856750	0		10	0	4	P	0.4	P
	X	SODIUM HYDROXIDE	DEVELOPER, SHIPLEY AZ 351	2.13	856442	0		5	0	12	GL	10.65852	P
	X	SODIUM HYDROXIDE	DEVELOPER, ORONALAR CDC-8	2.13	856111	1.38	96	5	0	6	GL	5.32926	P
		SOLDER, ALPHA 60/40	SOLDER, ALPHA 60/40							2709	P	2709.00	P
		SOLDER TIN/LEAD 62/36	SOLDER TIN/LEAD 62/36							50	P	50.00	P
	X	SULFURIC ACID	HACH MOLYBDATE 3 REAGENT	1.84	856602	1.28	96	20	0	3	GL	9.20736	P
	X	SULFURIC ACID	STRIPPER, ALLIED RT 2	1.84	856394	0		80	0	10044	P	123304.9651	P
		SULFURIC ACID	SULFURIC ACID	1.84						762660	P	762660.00	P
S	X	TRICHLOROTRIFLUOROETHANE	ACIDITY TEST KIT - PFPE	1.57	857157	1.49	96	90.9	0	25	EA	22.7	EA
S	X	TRICHLOROTRIFLUOROETHANE	FREON TA 55	1.57	856733	1.41	96	60	0	110	P	66	P
S	X	TRICHLOROTRIFLUOROETHANE	FREON TE	1.57	856764	1.51	96	96	0	8	GL	100.560384	P
S	X	TRICHLOROTRIFLUOROETHANE	FREON TF	1.57	856765	0		100	0	73830	P	73830	P
S	X	TRICHLOROTRIFLUOROETHANE	FREON TMC 55	1.57	856216	0		46	0	189	P	86.94	P
S	X	TRICHLOROTRIFLUOROETHANE	FREON TMS	1.57	856217	0		89	0	8780	P	7814.2	P
S	X	TRICHLOROTRIFLUOROETHANE	FREON TMS 650	1.57	856218	1.52	96	94	0	3780	P	3553.2	P
S	X	TRICHLOROTRIFLUOROETHANE	MS 136	1.57	856885	0		3	4	51	P	1.785	P
S	X	TRICHLOROTRIFLUOROETHANE	MS 180	1.57	856884	0		0	80	144	P	115.2	P
S	X	TRICHLOROTRIFLUOROETHANE	MS 190	1.57	856886	0		0	40.4	72	P	29.088	P
S	X	TRICHLOROTRIFLUOROETHANE	MS 230 CONTACT RE-NU	1.57		1.57	96	80	0	22	P	17.6	P
S	X	XYLENE	MARKER INK FORM B	0.86	856639	0.87	96	40	0	36.5	P	36.5	P
S	X	XYLENE	PHOTORESIST, HOECHST AZ 4903	0.86	856763	1.08	96	4	0	1.5	GL	0.430244	P
S	X	XYLENE	PHOTORESIST, KTI NEG 747	0.86	856455	0.87	96	36	92	747	GL	4607.693208	P
S	X	XYLENE	PHOTORESIST, SHIPLEY AZ 1370	0.86	856304	0		5	0	48	GL	17.21376	P
S	X	XYLENE	PHOTORESIST, SHIPLEY ECX 1000	0.86	856820	0		7	0	0.25	GL	0.125517	P
S	X	XYLENE	PHOTORESIST, SHIPLEY MICROPOST	0.86		0.6	96	7	0	0.25	GL	0.125517	P
S	X	XYLENE	PHOTORESIST, SHIPLEY S1400-17	0.86	856309	1.04	96	7	0	0.5	GL	0.251034	P
S	X	XYLENE	PHOTORESIST, SHIPLEY S1400-21	0.86	856542	0		7	0	4	GL	2.008272	P
S	X	XYLENE	PHOTORESIST, SHIPLEY S1400-27	0.86	856310	1.04	96	6	0	764	GL	328.782816	P
S	X	XYLENE	PHOTORESIST, SHIPLEY THINNER A	0.86	856311	1.04	96	9	0	220	GL	142.01352	P
S	X	XYLENE	PHOTORESIST, ULTRAMAC PR 914	0.86	856468	0		5	0	2	GL	0.71724	P
S	X	XYLENE	PHOTORESIST, WAYCOAT HNR 999	0.86	856328	0		89	0	35	GL	223.42026	P
S	X	XYLENE	PHOTORESIST, WAYCOAT HFR 294	0.86	856324	0		4	0	872	GL	250.173312	P
S	X	XYLENE	PHOTORESIST, WAYCOAT HFR 295	0.86	856325	0		4	0	132	GL	37.870272	P
S	X	XYLENE	PHOTORESIST, WAYCOAT HR 100	0.86	856318	0		87	0	708	GL	4417.911504	P
S	X	XYLENE	PHOTORESIST, WAYCOAT HR 200	0.86	856320	0		78	0	1774	GL	9924.593328	P
S	X	XYLENE	PHOTORESIST, WAYCOAT NEG VHR 3	0.86	856321	0		74	0	298	GL	1581.657648	P
S	X	XYLENE	PHOTORESIST, WAYCOAT SC 190	0.86	856317	0		72	0	176	GL	998.886528	P
S		XYLENE	XYLENE	0.86						8208	GL	58871.0592	P

JULY 1988 REPORTABLE CHEMICALS IN TOTAL POUNDS

	JULY REPORT CHEMICAL	TRADE CHEMICAL	DENS/PUREMSDS	DENS/M	FROM LTD	INDIC REC AMT	COMPONENT AMT	
S	1,1,1 TRICHLOROETHANE	TCA BUBBLERS	1.435	0	0	13 BBL	22.178276 P	
S	ML 1,1,1 TRICHLOROETHANE	TCA BUBBLERS/APACHE	1.435			11.2 KG	24.69152 P	
S	1,1,1 TRICHLOROETHANE	1,1,1 TRICHLOROETHANE	1.435			5024 GL	72994.5296 P	
S	1,1,1 TRICHLOROETHANE	1,1,1 TRICHLOROETHANE	1.435			10098 P	10098.00 P	
S	1,1,1 TRICHLOROETHANE	BURMAR EK34	1.435 856918	0	0	24 P	24 P	
S	1,1,1 TRICHLOROETHANE	CLEANER, ALPHA 565	1.435 856082	1.28 56	90	0	11 GL	118.48221 P
S	1,1,1 TRICHLOROETHANE	MS 136	1.435 856885	0	16	22	51 P	9.69 P
S	1,2,4 TRICHLOROBENZENE	STRIPPER, BURMAR 712D	1.45 856396	0	40	50	12740 GL	69329.169 P
S	ACETONE	ACETONE	0.79				37584 GL	248284.60 P
S	1 ACETONE	FREON TA 55	0.79 856733	1.41 56	10	30	110 P	22 P
	ML ALUMINUM OXIDE	ALUMINUM POWDER	3.99				2800 P	2800 P
	ALUMINUM OXIDE	ALUMINUM OXIDE	3.99				800 P	800.00 P
	AMMONIA	AMMONIA					350 P	350.00 P
S	Y AROMATIC PHENOL	STRIPPER, BURMAR 712D	1.0651 856396	0	15	25	12740 GL	22633.71583 P
	ARSINE 100 PPM	ARSINE 100 PPM			0.3		2320 CF	13.94 P
	ARSINE 100 PPM	ARSINE 100 PPM			0.3		10 CY	12.74 P
	ARSINE 15%	ARSINE 15%					45 CY	57.24 P
	ARSINE 15%	ARSINE 15%					58 CF	73.78 P
	ARSINE 25 PPM	ARSINE 25 PPM			0.2		3240 CF	19.40 P
	ARSINE 25 PPM	ARSINE 25 PPM			0.2		10 CY	12.72 P
	ARSINE 3000 PPM	ARSINE 3000 PPM			23.3		1392 CF	10.34 P
	ARSINE 3000 PPM	ARSINE 3000 PPM			23.8		5104 CF	37.99 P
	ARSINE 3000 PPM	ARSINE 3000 PPM			23.8		23 CY	36.20 P
S	ML BUTYL ALCOHOL	BUTYL ALCOHOL	0.78				8 GL	52.0416 P
	Y CADMIUM MERCURY SULFIDE	MARKEM INK FORM 4	856651	5.1 56	40	0	36.5 P	14.6 P
	Y CADMIUM SULFOSELENIDE RED	MARKEM INK FORM 3	856650	5.2 56	40	0	36.5 P	14.6 P
S	HL CARBON TETRACHLORIDE	CARBON TETRACHLORIDE	1.59				48 L	20.163744 P
	CHLORINE	CHLORINE CYLINDER	1.42				60 P	60 P
	Y CHROMIC ACID	STRIPPER, ALLIED RT 2	856394	0	1	0	10044 P	100.44 P
S	X CRESOL	MARKEM INK FORM D	1.026333 856641	1.03 56	30	70	36.5 P	18.25 P
S	X CRESOL	STRIPPER, HUNT MICROSTRIP	1.026333 856401	0	17	0	9135 GL	13292.66187 P
S	X DIMETHYL PHTHALATE	MARKEM INK FORM E	856642	0	0	0	36.5 P	36.5 P
S	X ETHYLBENZENE	PHOTORESIST, WAYCOAT HNR 999	0.87 856328	0	10	0	35 GL	25.3953 P
S	X ETHYLBENZENE	PHOTORESIST, WAYCOAT HR 100	0.87 856318	0	10	0	798 GL	513.71064 P
S	X ETHYLBENZENE	PHOTORESIST, WAYCOAT HR 200	0.87 856320	0	11	0	1774 GL	1415.896812 P
S	X ETHYLBENZENE	PHOTORESIST, WAYCOAT NEG VHR 3	0.87 856321	0	13	0	298 GL	261.889692 P
S	X ETHYLBENZENE	PHOTORESIST, WAYCOAT SC 100	0.87 856317	0	10	0	176 GL	127.70208 P
S	Y ETHYLENE GLYCOL MONOETHYL ACETMARKEM INK FORM H		856645	0.9 56	30	70	36.5 P	18.25 P
S	Y ETHYLENE GLYCOL MONOETHYL ACETMARKEM INK FORM I		856646	0.98 56	30	70	36.5 P	18.25 P
	X HF	ETCH, BUFFERED OXIDE ETCH 9:1	1.18	0	10	0	1464 GL	1440.75168 P
	HYDROCHLORIC ACID	TUBE TRAITER						58480 P
X	HYDROCHLORIC ACID	85-9-314	1.19 856161	1.19 56	10	0	1 P	0.1 P
	HYDROCHLORIC ACID	HYDROCHLORIC ACID	1.19				28080 P	28080.00 P
X	HYDROCHLORIC ACID	NICKEL B	1.19 857093	1.1 56	2	0	8 GL	1.574592 P
X	HYDROCHLORIC ACID	RTM SOLUTION B	1.19 857136	0	1	0	2 GL	0.196824 P
	HYDROFLUORIC ACID	HYDROFLUORIC ACID	1.18				61560 P	61560.00 P
	HYDROFLUORIC ACID 10:1	HYDROFLUORIC ACID 10:1	1.18			10	1296 GL	1275.41952 P
	HYDROFLUORIC ACID 40:1	HYDROFLUORIC ACID 40:1	1.18		0.4		4320 GL	170.055936 P
	HYDROGEN CHLORIDE	HYDROGEN CHLORIDE	1.19				68 CY	4880 P
	X HYDROQUINONE	DEVELOPER, CARNALAR CDC-A	1.31 856110	1.11 56	16	0	6 GL	10.468384 P
	HYDROQUINONE	HYDROQUINONE	1.31				0.5 KG	1.10 P
7	LEAD CHROMATE	MARKEM INK FORM 2	856649	5.9 56	40	0	36.5 P	14.5 P
S	METHANOL	METHANOL	0.79				11016 GL	72580.0176 P
S	X METHYL ALCOHOL	ETHYL ALCOHOL	0.79 856171	0	5	0	4632 L	42.0775488 P
S	X METHYL ALCOHOL	FREON TMS	0.79 856217	0	11	0	3780 P	965.3 P

*HARRIS SEMICONDUCTOR
CALENDAR YEAR 1987
VOC - MATERIAL BALANCE
ATTACHMENT 5
WASTE PROFILES*

WASTE COMMON NAME: MIXED SOLVENTS

DOT SHIPPING NAME: "RQ" WASTE FLAMMABLE LIQUID, NOS

DOT HAZARD CLASS : FLAMMABLE LIQUID

UN/NA NUMBER: UN1993

EPA ID # : F003, F005

AUTHORIZED BULK CONTAINER: SS: STEEL

AUTHORIZED DRUM CONTAINER: 17-E / 55 GALLON

***** CHEMICAL CHARACTERISTICS *****

COLOR: BROWN

ODOR: MILD - SWEET

pH: N/A

PHYSICAL STATE @70F: LIQUID

SPECIFIC GRAVITY: 0.8-1.0

PERCENT VOLUME FREE LIQ.: 90% +

LAYERS: 1 OR 2

FLASH POINT: < 70F

BTU/LB:

ASH CONTENT:

OTHER:

METALS (CONC. IN PPM)

ARSENIC: <5

BARIUM: <10

CADMIUM: <1

CHROMIUM: <5

MERCURY: <0.02

LEAD: <5

CHROMIUM (HEX): <5

SELENIUM: <1

SILVER: <5

COPPER: 5 - 50

NICKEL: <5

ZINC: 1 - 20

THALLIUM: ---

OTHERS:

CHEMICAL COMPOSITION	PERCENT	RQ
1.): ACETONE	1.): 20 - 55	1.): 5000
2.): METHANOL	2.): 10 - 40	2.): 5000
3.): ISOPROPANOL	3.): 10 - 40	3.): --
4.): N-BUTYL ACETATE	4.): 2 - 20	4.): --
5.): XYLENE	5.): 1 - 10	5.): 1000
6.): TOLUENE	6.): 1 - 10	6.): 1000
7.): HEXAMETHYLDISILAZANE	7.): 1 - 15	7.): --
8.): WATER	8.): 1 - 10	8.): --
9.): MIK, MEK, ETHYL ACETATE	9.): 1 - 5 @	9.): 5000 @
10.): CELLOSOLVE ACETATE, BENZENE	10.): 1 - 5 @	10.): 1000
11.): CHLORINATED HYDROCARBONS	11.): 1 - 5	11.): --
12.): AROM. & ALIPH. HYDROCARB.	12.): 3 - 20	12.): --

LABELS REQUIRED: FLAMMABLE

LOCATION:

PROCESS SOURCE: MANUFACTURING FAB

MSDS (HARRIS SPEC. # 856---):

SAFETY EQUIPMENT:

SPECIAL INSTRUCTIONS: RQ - 1000*

APPROVAL/DATE

Stephen Pfeffer 5/26/88

ENVIRONMENTAL SERVICES

REVISION DATE:

Attachment :



HARRIS

Purolator
6-30-88
722052414

file copy

June 29, 1988

RECEIVED

JUL 1 1988

Mr. A.T. Sawicki, P.E.
St. Johns River District
Florida Department of Environmental Regulation
3319 Maquire Blvd. Suite 232
Orlando, Florida 32803

DER-BAQM

Subject: Harris Semiconductor - Consolidated Air Permits

Dear Mr. Sawicki:

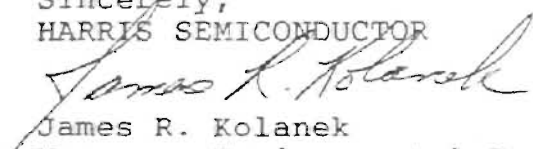
Enclosed please find the following information and attachments:

- Attachment I - Industrial Hygiene Information
By Building
- Attachment II - Air Dispersion Model
- Attachment III - Cogeneration Schedule
- Attachment IV - 1987 Solvent Material Balance

The enclosed information is the data that was previously requested by the DER at our meeting in Orlando. As a point of information, Harris is currently evaluating a proposal from a consultant on the Cogeneration Project. The consultant is currently obtaining additional information as to the feasibility of burning VOC/solvent emissions in a gas turbine. We shall keep you advised of any further developments on this subject.

If you should have any questions about the enclosed information, please feel free to contact me at (407) 724-7467.

Sincerely,
HARRIS SEMICONDUCTOR


James R. Kolanek
Manager, Environmental Services

c.c. Bruce Mitchell, DER Tallahassee

CHF/BT

Purolator courier

Purolator Account No. to be billed: 53-94-27799 Date: 6-30-88

722052414

Service - Check One - See reverse side for detail

Purolator Overnight Letter

Purolator Overnight Pack

Priority National Through Service Nationwide

Priority Regional Overnight Service

Standard 2-day Service

Optional Service

Saturday Deliv. Extra Charge

Hold for Pick-up

Payment

Sender Prepaid

Third Party Collect

Cash/Check

From - Sender's Name

DR. KSTANER

Sender's Area Code/Phone Number

(407) 244-7467

To - Recipient's Name

BRUCE MITCHELL

Recipient's Area Code/Phone Number

(904) 411-1111

Company Name

HARRIS SEMICONDUCTOR

Company Name

FLORIDA DER

Dept./Suite

Street Address

DALE RAY RD BLOC

Street Address (P.O. Box numbers not deliverable)

2600 BLAIR ST NW RD

City

DALE RAY

State

FL

Zip Code - Required

32905

City

TALLAHASSEE

State

FL

Zip Code - Required

32305

Sender's Signature

[Signature]

P.O. or Reference Number

Third Party Billing Name/ Address

118-59-055

22710



Weight	L	W	H
1			

Tariff	Rate Item	SM	Origin Airport	Destination Airport		
			<u>MLP</u>	<u>TLH</u>		
Advance	Valuation	Code	Amount	Code	Amount	Total Charge
Special Charge	DB	Route	Courier Guard Initial	S.S. - Last 4 digits	PUROLATOR USE ONLY	
	<input type="checkbox"/>		<u>[Initials]</u>	<u>[Initials]</u>		

B. 2 Rev. 4-85

RECIPIENT'S COPY

1000

722052414

1000 Kay, L
9-9-88

Puroator cover
722047855

file copy



FS-JRK-036-89

September 9, 1988

RECEIVED

Mr. Bruce Mitchell
State of Florida
Department of Environmental Regulations
Twin Tower Office Building
2600 Blair Stone Road
Tallahassee, Florida 32301

SEP 12 1988
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DER-BAQM

SEP 12 1988

DER-BAQM

Subject: Technical Evaluation and Preliminary
Determination AC05-147321 & AC05-150794

Dear Mr. Mitchell:

Per our conversation of August 19, 1988, we have reviewed the subject Technical Evaluation. In addition we have reviewed the methods utilized to calculate the projected air emissions from Building 54 and Building 59.

We are in agreement that the methods used to calculate the emissions should be consistent on each permit modification. As a result we have revised the calculation to established the annual emissions based on 8760 hours of production.

Please find enclosed a revised list of projected emissions from the Semiconductor facility on a by source basis. We would like these numbers incorporated in Tables 1 and 2 of the Technical Review.

If you should have any questions please call me at (407) 724-7467.

Sincerely,

James R. Kolanek
J. R. Kolanek, Manager
Environmental Services

/pgc

- cc: N. A. Baldisserotto
- D. R. Erdley
- L. R. Hutker
- R. R. Sands

copied: Bruce Mitchell
Chuck Collins, CF Tech
CHF/BT

ADDENDUM TO BUILDING 54 & 59 PERMIT APPLICATIONS

When solvent emission limits included in the building 54 permit application were initially estimated, the building's production and nonproduction hours were taken into account, and values were based on monitoring work performed during these time intervals. The building's projected emissions were based on an extrapolation derived from the following proportion:

$$\frac{A \text{ tpy}}{B \text{ tpy}} = \frac{C \text{ tpy}}{D \text{ tpy}}$$

where: A = maximum building emissions determined by EPA method 25-A monitoring.
B = maximum Semiconductor site emissions determined by EPA method 25-A monitoring.
C = building's projected emissions.
D = site's emission limit as discussed in the meeting between Semiconductor and FDER in February of 1988.

However, a problem arises with this method due to the potential for fluctuating production activity, as was the case when the methodology had to be altered to accommodate the increased production activity when applying for building 59's air permit. In order to establish consistency in estimating VOC emissions from Semiconductor's buildings, releases will be calculated based on the maximum potential production schedule for each building; 24 hours a day, 365 days a year (in other words, 8760 hours a year.) The total yearly VOC emissions listed in attachment represent maximum yearly atmospheric loading, which equates to 152.50 tons/yr.

Total projected VOC emissions for building 54 is 95.65 tons/year as opposed to 94.34 tons/year initially calculated and submitted in the application.

Total projected VOC emissions for building 59 is 0.50 tons/year instead of 0.57 tons/year initially extrapolated for this building.

Assumptions previously stated remain consistent:

- Emission values for F54S02 & F54S04 are assumed to be equal to F54S01 & F54S03, respectively. This is because each pair handle exhaust from a common duct.
- VOC values refer to all organic emissions including organic solvents.
- All data is corrected for 2 ppm background concentration of VOC's that is present in the ambient air.
- The F.I.D. acumulative emission figure is based on the maximum concentration observed during the monitoring timeframe.

WALVENT SCRUBBERS--HARRIS SEMICONDUCTOR

BLDG	SCRUBBER#	PRODUCTION SCHEDULE (hrs/yr)	TOTAL YEARLY VOC EMISSIONS (ton/yr)	total by bldg
04	F04S01	8760	0.26	10.96
04	F04S02	8760	min	
04	F04S03	8760	1.93	
04	F04S08	8760	8.77	
51	F51S02	8760	11.39	33.29
51	F51S03	8760	3.72	
51	F51S04	8760	1.71	
51	F51S05	8760	16.47	95.65
54	F54S01	8760	15.24	
54	F54S02	8760	15.24	
54	F54S03	8760	32.59	
54	F54S04	8760	32.59	1.66
57	F57S01	8760	1.66	
58	F58S01	8760	2.82	3.24
58	F58S02	8760	0.41	
59	F59S03	8760	0.50	0.50
60	F60S01	8760	min	
61	F61S01	8760	0.25	0.25
62	F62S02	8760	0.83	
63	F63S02	8760	2.02	6.14
63	F63S03	8760	4.12	

			152.50	

* When multiple testing was performed, values are indicative of highest VOC concentrations observed.

CAPE PUBLICATIONS, INC.

The Times

Published Weekly on Wednesday

THE TRIBUNE

Published Weekly on Wednesday

RECEIVED

OCT 6 1988



Published Daily

DER - BAQM

STATE OF FLORIDA
COUNTY OF BREVARD

Before the undersigned authority personally appeared Linda L. Spicer who on oath says that he/she is Legal Advertising Clerk

of the FLORIDA TODAY, a newspaper published in Brevard County,

Florida; that the attached copy of advertising being a

Notice of Intent

in the matter of

permits to Harris Semiconductor

in the Court

was published in the FLORIDA TODAY NEWSPAPER

in the issues of September 30, 1988

Affiant further says that the said FLORIDA TODAY NEWSPAPER

is a newspaper published in said Brevard County, Florida and that the said newspaper has heretofore been continuously published in said Brevard County, Florida regularly as stated above, and has been entered as second class mail matter at the post office in COCOA

said Brevard County, Florida for a period of one year next preceeding the first publication of the attached copy of advertisement; and affiant further says that he has neither paid nor promised any person, firm or corporation any discount, rebate, commission or refund for the purpose of securing this advertisement for publication in said newspaper.

Linda L. Spicer (handwritten signature)

Sworn and subscribed to before me this

30th day of September A.D., 19 88

Cathy S. Smith (handwritten signature)

Notary Public
State of Florida at Large
My Commission Expires March 29, 1992

State of Florida
Department of
Environmental Regulation
Notice of Intent

The Department of Environmental Regulation hereby gives notice of its intent to issue a permit to Harris Semiconductor to consolidate multiple permits previously issued for Buildings No. 54 and No. 59, which are water fabrication sources and located at the applicant's existing facility on Palm Bay Road in the City of Palm Bay, Brevard County, Florida. The Department is issuing this intent to issue for the reasons stated in the Technical Evaluation and Preliminary Determination.

Persons whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative determination (hearing) in accordance with Section 120.57, Florida Statutes. The petition must conform to the requirements of Chapters 17-103 and 28-5, Florida Administrative Code, and must be filed (received) in the Department's Office of General Counsel, 2600 Blair Stone Road, Twin Towers Office Building, Tallahassee, Florida 32399-2400, within fourteen (14) days of publication of this notice. Failure to file a petition within this time period constitutes a waiver of any right such person has to request an administrative determination (hearing) under Section 120.57, Florida Statutes.

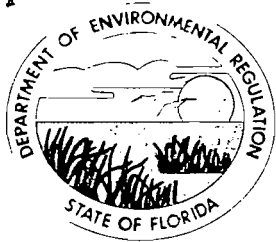
If a petition is filed, the administrative hearing process is designed to formulate agency action. Accordingly, the Department's final action may be different from the proposed agency action. Therefore, persons who may not wish to file a petition may wish to intervene in the proceeding. A petition for intervention must be filed pursuant to Rule 28-3.207, Florida Administrative Code, at least five (5) days before the final hearing and be filed with the hearing officer if one has been assigned at the Division of Administrative Hearings, Department of Administration, 2009 Apalachee Parkway, Tallahassee, Florida 32301. If no hearing officer has been assigned, the petition is to be filed with the Department's Office of General Counsel, 2600 Blair Stone Road, Tallahassee, Florida 32399-2400. Failure to petition to intervene within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, Florida Statutes.

The applications are available for public inspection during normal business hours, 8:00 a.m. to 5:00 p.m., Monday through Friday, except legal holidays, at: Dept. of Environmental Regulation, Bureau of Air Quality Management, 2600 Blair Stone Road, Tallahassee, Florida 32399-2400

Dept. of Environmental Regulation
Central Florida District
3319 Maguire Blvd., Suite 222
Orlando, Florida 32803-3747

Any person may send written comments on the proposed action to Mr. Bill Thomas at the Department's Tallahassee address. All comments mailed within 14 days of the publication of this notice will be considered in the Department's final determination.
T093315-1T-9/30/88, Friday

(Handwritten notes and signature)



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Bob Martinez, Governor

Dale Twachtman, Secretary

John Shearer, Assistant Secretary

September 19, 1988

CERTIFIED MAIL-RETURN RECEIPT REQUESTED

Mr. James R. Kolanek
Manager, Environmental Services
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32901

Dear Mr. Kolanek:

Attached is one copy of the Technical Evaluation and Preliminary Determination and proposed permits for Harris Semiconductor for Buildings No. 54 and No. 59, in order to consolidate multiple permits previously issued for the sources/buildings. Buildings No. 54 and No. 59 are wafer fabrication sources.

Please submit any written comments you wish to have considered concerning the Department's proposed action to Mr. Bill Thomas of the Bureau of Air Quality Management.

Sincerely,

C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management

CHF/

Attachments

cc: C. Collins, Cent. FL Dist.
L. R. Hutker, P.E., HS
B. Pittman, Esq., DER

BEFORE THE STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

In the Matter of
Application for Permits by:

Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32901

DER File Nos. AC 05-147321
AC 05-150794

INTENT TO ISSUE

The Department of Environmental Regulation hereby gives notice of its intent to issue permits (copy attached) for the proposed project as detailed in the applications specified above. The Department is issuing this Intent to Issue for the reasons stated in the attached Technical Evaluation and Preliminary Determination.

The applicant, Harris Semiconductor, applied on March 3, 1988 and June 10, 1988, respectively, to the Department of Environmental Regulation for permits to consolidate multiple permits issued previously for Buildings No. 54 and No. 59, which are wafer fabrication sources. The sources/buildings are located at the applicant's existing facility on Palm Bay Road in the City of Palm Bay, Brevard County, Florida.

The Department has permitting jurisdiction under Chapter 403, Florida Statutes, and Florida Administrative Code Rules 17-2 and 17-4. The project is not exempt from permitting procedures. The Department has determined that an air construction permits were needed for the proposed work.

Pursuant to Section 403.815, F.S. and DER Rule 17-103.150, FAC, you (the applicant) are required to publish at your own expense the enclosed Notice of Proposed Agency Action on the permit applications. The notice must be published one time only in a section of a major local newspaper of general circulation in the county in which the project is located and within thirty (30) days from receipt of this intent. Proof of publication must be provided to the Department within seven days of publication of the notice. Failure to publish the notice and provide proof of publication within the allotted time may result in the denial of the permits.

The Department will issue the permits with the attached conditions unless a petition for an administrative proceeding (hearing) is filed pursuant to the provisions of Section 120.57, F.S. A person whose substantial interests are affected by the

Department's proposed permitting decision may petition for an administrative proceeding (hearing) in accordance with Section 120.57, Florida Statutes. Petitions must comply with the requirements of Florida Administrative Code Rules 17-103.155 and 28-5.201 (copy enclosed) and be filed with (received by) the Office of General Counsel of the Department at 2600 Blair Stone Road, Tallahassee, Florida 32399-2400. Petitions filed by the permit applicant must be filed within fourteen (14) days of receipt of this intent. Petitions filed by other persons must be filed within fourteen (14) days of publication of the public notice or within fourteen (14) days of receipt of this intent, whichever first occurs. Failure to file a petition within this time period shall constitute a waiver of any right such person may have to request an administrative determination (hearing) under Section 120.57, Florida Statutes, concerning the subject permit applications. Petitions which are not filed in accordance with the above provisions will be dismissed.

Executed in Tallahassee, Florida.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION



C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management

Copies furnished to:

C. Collins, Cent. FL Dist.
L. R. Hutker, P.E., HS
B. Pittman, Esq., DER

CERTIFICATE OF SERVICE

The undersigned duly designated deputy clerk hereby certifies that this NOTICE OF INTENT TO ISSUE and all copies were mailed before the close of business on 9-19-88.

FILING AND ACKNOWLEDGEMENT
FILED, on this date, pursuant to
§120.52(9), Florida Statutes, with
the designated Department Clerk,
receipt of which is hereby
acknowledged.

Jeddy Rogers
Clerk

9-19-88
Date

RULES OF THE ADMINISTRATIVE COMMISSION
MODEL RULES OF PROCEDURE
CHAPTER 28-5
DECISIONS DETERMINING SUBSTANTIAL INTERESTS

28-5.15 Requests for Formal and Informal Proceedings

- (1) Requests for proceedings shall be made by petition to the agency involved. Each petition shall be printed, typewritten or otherwise duplicated in legible form on white paper of standard legal size. Unless printed, the impression shall be on one side of the paper only and lines shall be double spaced and indented.
- (2) All petitions filed under these rules should contain:
 - (a) The name and address of each agency affected and each agency's file or identification number, if known;
 - (b) The name and address of the petitioner or petitioners;
 - (c) All disputed issues of material fact. If there are none, the petition must so indicate;
 - (d) A concise statement of the ultimate facts alleged, and the rules, regulations and constitutional provisions which entitle the petitioner to relief;
 - (e) A statement summarizing any informal action taken to resolve the issues, and the results of that action;
 - (f) A demand for the relief to which the petitioner deems himself entitled; and
 - (g) Such other information which the petitioner contends is material.

State of Florida
Department of Environmental Regulation
Notice of Intent

The Department of Environmental Regulation hereby gives notice of its intent to issue permits to Harris Semiconductor to consolidate multiple permits previously issued for Buildings No. 54 and No. 59, which are wafer fabrication sources and located at the applicant's existing facility on Palm Bay Road in the City of Palm Bay, Brevard County, Florida. The Department is issuing this Intent to Issue for the reasons stated in the Technical Evaluation and Preliminary Determination.

Persons whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative determination (hearing) in accordance with Section 120.57, Florida Statutes. The petition must conform to the requirements of Chapters 17-103 and 28-5, Florida Administrative Code, and must be filed (received) in the Department's Office of General Counsel, 2600 Blair Stone Road, Twin Towers Office Building, Tallahassee, Florida 32399-2400, within fourteen (14) days of publication of this notice. Failure to file a petition within this time period constitutes a waiver of any right such person has to request an administrative determination (hearing) under Section 120.57, Florida Statutes.

If a petition is filed, the administrative hearing process is designed to formulate agency action. Accordingly, the Department's final action may be different from the proposed agency action. Therefore, persons who may not wish to file a petition may wish to intervene in the proceeding. A petition for intervention must be filed pursuant to Rule 28-5.207, Florida Administrative Code, at least five (5) days before the final hearing and be filed with the hearing officer if one has been assigned at the Division of Administrative Hearings, Department of Administration, 2009 Apalachee Parkway, Tallahassee, Florida 32301. If no hearing officer has been assigned, the petition is to be filed with the Department's Office of General Counsel, 2600 Blair Stone Road, Tallahassee, Florida 32399-2400. Failure to petition to intervene within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, Florida Statutes.

The applications are available for public inspection during normal business hours, 8:00 a.m. to 5:00 p.m., Monday through Friday, except legal holidays, at:

Dept. of Environmental Regulation
Bureau of Air Quality Management
2600 Blair Stone Road
Tallahassee, Florida 32399-2400

Dept. of Environmental Regulation
Central Florida District
3319 Maguire Blvd., Suite 232
Orlando, Florida 32803-3767

Any person may send written comments on the proposed action to Mr. Bill Thomas at the Department's Tallahassee address. All comments mailed within 14 days of the publication of this notice will be considered in the Department's final determination.

Technical Evaluation
and
Preliminary Determination

Harris Semiconductor
Brevard County
Palm Bay, Florida

Construction Permit Numbers:
AC 05-147321
AC 05-150794

Florida Department of Environmental Regulation
Division of Air Resources Management
Bureau of Air Quality Management
Central Air Permitting

September 19, 1988

I. Application

A. Applicant

Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32901

B. Project and Location

The applicant has applied for construction permits for Buildings No. 54 and No. 59, in order to consolidate multiple permits previously issued for these sources/buildings.

The existing facility is located on Palm Bay Road, City of Palm Bay, Florida. The UTM coordinates are Zone 17, 538.7 km East and 3100.9 km North.

C. Process and Controls

1. Building 54

Building 54 is a wafer fabrication facility. The second floor of the two-story building houses two clean room modules. Both fabrication areas employ a series of manufacturing procedures referred to as layering, patterning, doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

Wet stations that house vats containing a variety of acid and caustic compounds are located throughout the clean rooms. Storage cabinets safely hold virgin chemicals until they are ready for use. The first floor of the building contains exhausted gas cabinets that supply process gases to the 'fab' operations.

The exhaust system for the building is divided into two sections. The west half exhaust is fed into a common duct that is divided into two wet scrubber systems, F54S01 and F54S02, at ground level. The east portion of the building exhaust is ducted to a common line that divides into two wet scrubbers (F54S03 and F54S04) on the east side of building. Also on the east side of Building 54 is a non-scrubbed exhaust fan F54E17 that handles air flow from several aligners, furnace source cabinets, and gas cabinets.

2. Building 59

Building 59 houses a wafer fabrication facility on the second floor. The fabrication area employs a series of manufacturing procedures referred to as layering, patterning,

doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

Thirteen exhausted wet stations that house vats containing a variety of acid and caustic compounds are in the fabrication facility. Five of these stations contain solvents, one of which is heated.

The ground floor of the two-story manufacturing area houses a process equipment support room that contains gas cabinets, chemical storage cabinets, vacuum pumps and drains. These exhausted units service the process equipment which resides above it in the fabrication area. Storage cabinets safely hold virgin chemicals until they are ready for use. Gas cabinets house cylinders that supply process gases to the 'fab' operations. In addition, several waste collection areas are exhausted. The ground floor also houses the site's distilled water plant and a mechanical equipment storage area.

The exhaust system for the building is divided between two scrubbers. Acid vapors are vented to scrubber number F59S01, while solvent exhaust streams are ducted to scrubber number F59S03. Both systems reside on the site grounds directly outside the west wall of the building.

3. General

In the controlled environment of the fabrication clean room, wafer surfaces first undergo acid and/or solvent cleaning followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "aligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers are hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques.

In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Fumes from the vapor deposition furnaces are oxidized in burn boxes. The oxidized gases are then exhausted to scrubber systems. Additional material may be layered on the wafer surface in vapor and

crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation.

A material balance scheme will be used to account for the annual VOC/solvent emissions released into the atmosphere by the facility. A program of sampling and analysis will be used to assess the VOC/solvent emissions from each building.

The Standard Industrial Classification Codes are:

- o Major Group 36: Electrical and Electronic Machinery, Equipment, and Supplies
- o Industry Group No. 367: Electronic Components and Accessories
- o Industry No. 3674: Semiconductors and Related Devices

The Source Classification Codes are:

- o Major Group 36: Organic Solvent Evaporation
- o Building 54 4-01-003-99 Tons VOC/solvent consumed
- o Building 59 4-01-003-99 Tons VOC/solvent consumed

II. Rule Applicability

The proposed project is subject to preconstruction review under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code (FAC) Rules 17-2 and 17-4.

The application packages were deemed complete on July 1, 1988.

The existing facility is located in an area designated attainment for all pollutants. Therefore, review of emissions shall be in accordance with FAC Rule 17-2.500, Prevention of Significant Deterioration (PSD).

Since the facility is not one of those contained in Table 500-1, FAC Rule 17-2, the VOC/solvent threshold for triggering new source review pursuant to FAC Rule 17-2.500(5) is 250 TPY.

The following table presents the projected potential VOC/solvent emissions:

Table 1

Source	Potential VOC/solvent Emissions (TPY)
Building 54	
o F54S01	15.24
o F54S02	15.24
o F54S03	32.59
o F54S04	32.59
Building 59	
o F59S03	0.50
Total:	<u>96.16</u>

Note: 1. Annual hours of operation at 8760.

The following table presents the projected potential VOC/solvent emissions from the facility:

Table 2

Building	Potential VOC/solvent Emissions (TPY)
4	10.96
51	33.29
54	95.65
57	1.66
58	3.24
59	0.50
60	min.
61	0.25
62	0.83
63	6.14
Total:	<u>152.50</u>

Since the potential emissions are less than 250 TPY for the facility, the potential emissions projected from Buildings 54 and 59 will be reviewed pursuant to FAC Rule 17-2.520, Sources Not Subject to PSD or Nonattainment Requirements.

Since there is no specific emission limiting standard contained in FAC Rule 17-2.600 nor is there any standards of performance for new stationary sources contained in FAC Rule 17-2.660, the sources will be permitted in accordance with FAC Rule 17-2.620, General Pollutant Emission Limiting Standards.

In FAC Rule 17-2.620(1)(a), no person shall store, pump, handle, process, load, unload or use in any process or installation volatile organic compounds or organic solvents without applying known and existing vapor emission control devices or systems deemed necessary and ordered by the Department. Pursuant to FAC Rule 17-2.620(2), no person shall cause, suffer, allow or

permit the discharge of air pollutants which cause or contribute to an objectionable odor. Objectionable odor is defined as any odor present in the outdoor atmosphere, which by itself or in combination with other odors, is or may be harmful or injurious to human health or welfare, which unreasonably interferes with the comfortable use and enjoyment of life or property, or which creates a nuisance according to FAC Rule 17-2.100(132).

The buildings operations/sources are subject to the provisions of FAC Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; 17-4.130: Plant Operation-Problems; and, 17-4.140: Reports.

III. Summary of Emissions

A. Emission Limitations

The regulated pollutant emissions from these buildings/sources are VOC/solvents in accordance with FAC Rule 17-2.620.

Specific acid solutions are also being used during the manufacturing operations. There are no specific emission limiting standards for these specific acids. However, the acid vapors will be scrubbed to reduce emissions.

The following table presents the allowable VOC/solvent emissions and the potential acid vapor emissions from Buildings 54 and 59 in TPY:

Table 3

Building	Maximum Allowable VOC/Solvent Emissions	Potential Acid Vapor Emissions
54	95.7	
59	0.5	0.1

Note: Hours of operation are 8760.

The permitted emissions are in compliance with all requirements of FAC Rules 17-2 and 17-4.

B. Air Quality Impacts

From the technical review of the application packages and supplementary material, an air quality analysis was not required.

V. Conclusion

The maximum allowable VOC/solvent emissions from Buildings 54 and 59 are in compliance with FAC Rules 17-2 and 17-4. Even though there are no emission standards for acid vapors, the

applicant has installed scrubber systems to control their emissions.

A system of material balance and sampling/analysis will be used to account for and verify pollutant emissions from each building and their scrubber systems.

The General and Specific Conditions listed in the proposed permits (attached) will ensure compliance with all applicable requirements of FAC Rules 17-2 and 17-4.



Florida Department of Environmental Regulation

Twin Towers Office Bldg. • 2600 Blair Stone Road • Tallahassee, Florida 32399-2400

Lawton Chiles, Governor

Carol M. Browner, Secretary

December 4, 1991

CERTIFIED MAIL - RETURN RECEIPT REQUESTED

Mr. Robert R. Padron, General Manager
Utility Board - City of Key West
City Electric System
Post Office Drawer 6100
Key West, Florida 33041-6100

Dear Mr. Padron:

Re: Expiration Date Extension for Construction Permit
AC 44-152197 (PSD-FL-135)

The Department has reviewed the above request contained in Ms. Diane D. Tremor's letters received October 30 and November 21, 1991, of which the latter included the appropriate processing fee. The request is acceptable and the following will be changed and added:

1. Expiration Date

From: December 31, 1991
To: May 1, 1992

2. Attachments to be Incorporated

- o Ms. Diane D. Tremor's letter received October 30, 1991.
- o Ms. Diane D. Tremor's letter and processing fee received November 21, 1991.

This letter must be attached to the construction permit, No. AC 44-152197 (PSD-FL-135), and shall become a part of the permit.

Sincerely,

STEVE SMALLWOOD, P.E.
Director
Division of Air Resources
Management

Mr. Robert R. Padron
Page Two

SS/BM/rbm

Attachments

cc: D. Knowles, SD
R. Helbling, SDBO
J. Harper, EPA
C. Shaver, NPS
D. Tremor, Esq., RS&B

LAW OFFICES

ROSE, SUNDBSTROM & BENTLEY

A PARTNERSHIP INCLUDING PROFESSIONAL ASSOCIATIONS

2548 BLAIRSTONE PINES DRIVE

TALLAHASSEE, FLORIDA 32301

(904) 877-6555

RECEIVED
DER - MAIL ROOM

1991 NOV 21 AM 11:00

ROBERT A. ANTISTA
CHRIS H. BENTLEY, P.A.
F. MARSHALL DETERDING
MARTIN S. FRIEDMAN, P.A.
JOHN R. JENKINS
ROBERT M. C. ROSE, P.A.
WILLIAM E. SUNDBSTROM, P.A.
DIANE D. TREMOR
JOHN L. WHARTON

MAILING ADDRESS
POST OFFICE BOX 1567
TALLAHASSEE, FLORIDA 32302-1567

TELECOPIER (904) 656-4029

November 20, 1991

JOHN R. WODRASKA
SPECIAL CONSULTANT
(NOT A MEMBER OF THE FLORIDA BAR)

Mr. Clair H. Fancy
Deputy Chief
Bureau of Air Quality Management
Department of Environmental
Regulation
2600 Blair Stone Road
Tallahassee, Florida 32399-2400

Re: Key West Utility Board, Stock Island Power Plant;
Fee for Request for Extension of Permit Expiration Date
AC 44-152197 and PSD-FL-135

Dear Mr. Fancy:

In accordance with instructions from Patty Adams, I am enclosing a check in the amount of \$50.00 in connection with the request of Key West Utility Board, by correspondence dated October 30, 1991, for an extension of the expiration date of the referenced construction permit for the diesel generator project at the Stock Island Power Plant in Key West, Florida.

It is my understanding that, effective October 30, 1991, a \$50.00 fee is now required for requests for extension of permit expiration dates.

Please advise me if any further documentation is necessary in order to process our request for extension of the expiration date from December 31, 1991, to May 1, 1992.

Very sincerely yours,



Diane D. Tremor
For the Firm

DDT:sa
Enclosure

cc: Mr. Robert Padron
Mr. Robert Wallace
Bruce Mitchell, DER, Bureau of Air Quality

901033
1031

LAW OFFICES

ROSE, SUNDSTROM & BENTLEY

A PARTNERSHIP INCLUDING PROFESSIONAL ASSOCIATIONS

2548 BLAIRSTONE PINES DRIVE

TALLAHASSEE, FLORIDA 32301

(904) 877-6555

RECEIVED

OCT 30 1991

Division of Air
Resources Management

ROBERT A. ANTISTA
CHRIS H. BENTLEY, P.A.
F. MARSHALL DETERDING
MARTIN S. FRIEDMAN, P.A.
JOHN R. JENKINS
ROBERT M. C. ROSE, P.A.
WILLIAM E. SUNDSTROM, P.A.
DIANE D. TREMOR
JOHN L. WHARTON

MAILING ADDRESS
POST OFFICE BOX 1567
TALLAHASSEE, FLORIDA 32302-1567

TELECOPIER (904) 656-4029

October 30, 1991

JOHN R. WODRASKA
SPECIAL CONSULTANT
(NOT A MEMBER OF THE FLORIDA BAR)

Mr. Clair H. Fancy
Deputy Chief
Bureau of Air Quality Management
Department of Environmental
Regulation
2600 Blairstone Road
Tallahassee, Florida 32399-2400

Re: Utility Board of the City of Key West
Extension of Permit Expiration Date
AC 44-152197 and PSD-FL-135

Dear Mr. Fancy:

Pursuant to our telephone conversation, this letter is to confirm the request of the Utility Board of the City of Key West for a further extension of the expiration date of the referenced construction permit for the diesel generator project at the Stock Island Power Plant. The requested extension is from December 31, 1991, to May 1, 1992.

The reason for this current request is our initial dissatisfaction with the results of the long-term performance testing conducted on behalf of the contractor. We do not believe it would be appropriate to apply for an operating permit until we are provided greater assurance that the diesel units will perform in full compliance with all applicable laws and regulations, and in accordance with the terms of our contract.

Testing to ensure that the diesel units meet all performance guarantees pursuant to the terms of our contract was conducted in August. While the results from the beginning portion (the first 100 hours) of the required 360-hour performance testing indicated compliance with our DER construction permit conditions, the results near the end of the 360-hour test period indicated increasing opacity or visual emissions from one of the units. We have discussed this situation with the contractor and it was agreed that additional testing will be performed during the first full week of

November, 1991. We intend to submit to the DER a new report containing the results of the upcoming compliance testing.

In order to meet the requirements of our construction permit with regard to the timely submission of an application for an operating permit, and to obtain assurance that the units will be in full compliance with all applicable regulations, we are requesting an extension of the expiration date of the construction permit to May 1, 1992. This should afford us sufficient time to complete whatever modifications may be required, complete the new testing and timely submit an application for an operating permit for this project. Within 45 days from the completion of any required modifications and successful compliance testing, or 90 days prior to the requested extended expiration date of the construction permit, whichever first occurs, the Utility Board will submit its operating permit application.

Your continued assistance and cooperation is greatly appreciated. Should you need additional information regarding this extension request, please feel free to contact me.

Very sincerely yours,



Diane D. Tremor
For the Firm

DDT:sa

cc: Mr. Robert Padron, General Manager, City Electric System
Mr. Robert W. Wallace, City Electric System
Mr. Marc K. Anderson, City Electric System
Mr. Skip Jansen, City Electric System
Mr. Dale Finigan, City Electric System
Ms. Becky Pattinson, R. W. Beck and Associates, Inc.
Mr. Garry Cornish, R. W. Beck and Associates, Inc.
Mr. R. J. Helbling, DER, Marathon office
Mr. D. M. Knowles, DER, Fort Myers

M. King
B. Mitchell

LAW OFFICES

ROSE, SUNDSTROM & BENTLEY

A PARTNERSHIP INCLUDING PROFESSIONAL ASSOCIATIONS

2548 BLAIRSTONE PINES DRIVE

TALLAHASSEE, FLORIDA 32301

(904) 877-6555

ROBERT A. ANTISTA
CHRIS H. BENTLEY, P.A.
F. MARSHALL DETERDING
MARTIN S. FRIEDMAN, P.A.
JOHN R. JENKINS
ROBERT M. C. ROSE, P.A.
WILLIAM E. SUNDSTROM, P.A.
DIANE D. TREMOR
JOHN L. WHARTON

JOHN R. WODRASKA
SPECIAL CONSULTANT
(NOT A MEMBER OF THE FLORIDA BAR)

MAILING ADDRESS
POST OFFICE BOX 1567
TALLAHASSEE, FLORIDA 32302-1567

TELECOPIER (904) 656-4029

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NOV 21 1991

Division of Air
Resources Management

November 20, 1991

Mr. Clair H. Fancy
Deputy Chief
Bureau of Air Quality Management
Department of Environmental
Regulation
2600 Blair Stone Road
Tallahassee, Florida 32399-2400

Re: Key West Utility Board, Stock Island Power Plant;
Fee for Request for Extension of Permit Expiration Date
AC 44-152197 and PSD-FL-135

Dear Mr. Fancy:

In accordance with instructions from Patty Adams, I am enclosing a check in the amount of \$50.00 in connection with the request of Key West Utility Board, by correspondence dated October 30, 1991, for an extension of the expiration date of the referenced construction permit for the diesel generator project at the Stock Island Power Plant in Key West, Florida.

It is my understanding that, effective October 30, 1991, a \$50.00 fee is now required for requests for extension of permit expiration dates.

Please advise me if any further documentation is necessary in order to process our request for extension of the expiration date from December 31, 1991, to May 1, 1992.

Very sincerely yours,



Diane D. Tremor
For the Firm

DDT:sa

Enclosure

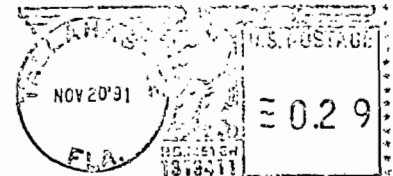
cc: Mr. Robert Padron
Mr. Robert Wallace
Bruce Mitchell, DER, Bureau of Air Quality

LAW OFFICES

ROSE, SUNDSTROM & BENTLEY

A PARTNERSHIP INCLUDING PROFESSIONAL ASSOCIATIONS

2548 BLAIRSTONE PINES DRIVE
TALLAHASSEE, FLORIDA 32301



Mr. Bruce Mitchell
Bureau of Air Quality Management
Department of Environmental
Regulation
2600 Blair Stone Road
Tallahassee, Florida 32399-2400



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TALLAHASSEE, FLORIDA 32301

(904) 877-6555

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OCT 30 1991

Division of Air
Resources Management

ROBERT A. ANTISTA
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MAILING ADDRESS
POST OFFICE BOX 1567
TALLAHASSEE, FLORIDA 32302-1567

TELECOPIER (904) 656-4029

October 30, 1991

JOHN R. WODRASKA
SPECIAL CONSULTANT
(NOT A MEMBER OF THE FLORIDA BAR)

Mr. Clair H. Fancy
Deputy Chief
Bureau of Air Quality Management
Department of Environmental
Regulation
2600 Blairstone Road
Tallahassee, Florida 32399-2400

Re: Utility Board of the City of Key West
Extension of Permit Expiration Date
AC 44-152197 and PSD-FL-135

Dear Mr. Fancy:

Pursuant to our telephone conversation, this letter is to confirm the request of the Utility Board of the City of Key West for a further extension of the expiration date of the referenced construction permit for the diesel generator project at the Stock Island Power Plant. The requested extension is from December 31, 1991, to May 1, 1992.

The reason for this current request is our initial dissatisfaction with the results of the long-term performance testing conducted on behalf of the contractor. We do not believe it would be appropriate to apply for an operating permit until we are provided greater assurance that the diesel units will perform in full compliance with all applicable laws and regulations, and in accordance with the terms of our contract.

Testing to ensure that the diesel units meet all performance guarantees pursuant to the terms of our contract was conducted in August. While the results from the beginning portion (the first 100 hours) of the required 360-hour performance testing indicated compliance with our DER construction permit conditions, the results near the end of the 360-hour test period indicated increasing opacity or visual emissions from one of the units. We have discussed this situation with the contractor and it was agreed that additional testing will be performed during the first full week of

November, 1991. We intend to submit to the DER a new report containing the results of the upcoming compliance testing.

In order to meet the requirements of our construction permit with regard to the timely submission of an application for an operating permit, and to obtain assurance that the units will be in full compliance with all applicable regulations, we are requesting an extension of the expiration date of the construction permit to May 1, 1992. This should afford us sufficient time to complete whatever modifications may be required, complete the new testing and timely submit an application for an operating permit for this project. Within 45 days from the completion of any required modifications and successful compliance testing, or 90 days prior to the requested extended expiration date of the construction permit, whichever first occurs, the Utility Board will submit its operating permit application.

Your continued assistance and cooperation is greatly appreciated. Should you need additional information regarding this extension request, please feel free to contact me.

Very sincerely yours,



Diane D. Tremor
For the Firm

DDT:sa

cc: Mr. Robert Padron, General Manager, City Electric System
Mr. Robert W. Wallace, City Electric System
Mr. Marc K. Anderson, City Electric System
Mr. Skip Jansen, City Electric System
Mr. Dale Finigan, City Electric System
Ms. Becky Pattinson, R. W. Beck and Associates, Inc.
Mr. Garry Cornish, R. W. Beck and Associates, Inc.
Mr. R. J. Helbling, DER, Marathon office
Mr. D. M. Knowles, DER, Fort Myers

M. Baig
B. Mitchell



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FS-JRK-185-88

JUN 10 1988

June 8, 1988

DER-BAQM

Mr. C. H. Fancy
Deputy Bureau Chief
Department of Environmental Regulation
Bureau of Air Quality Management
2600 Blair Stone Road
Tallahassee, Florida 32301

Reference: HARRIS SEMICONDUCTOR
B-59 Consolidated Air Permit

Dear Mr. Fancy:

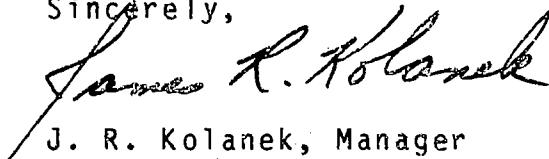
On February 17, 1988, representatives from Harris and the Florida DER met in Orlando to discuss the status of air permits at Harris Semiconductor's facility in Palm Bay. At that meeting it was agreed that Harris would submit modified air permits. The purpose of the permit modifications was as follows:

1. Consolidate permits on a by building basis to reduce the existing number of permits.
2. To accurately quantify the current air emissions.

Enclosed is the modified permit application for Semiconductor's Building 59.

If you should have any questions about the enclosed information, please feel free to contact me at (407) 724-7467.

Sincerely,


J. R. Kolanek, Manager
Environmental Services

/pgc

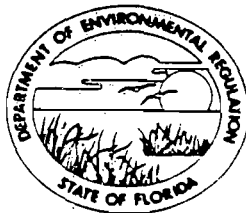
cc: A. T. Sawicki
L. R. Hutker
D. R. Erdley
R. R. Sands

DEPARTMENT OF ENVIRONMENTAL REGULATION

AC 05-150794

#100 pd
6-10-88

WIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



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BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

JUN 10 1988

6-13-88

APPLICATION TO OPERATE/CONSTRUCT AIR POLLUTION SOURCE

SOURCE TYPE: Stationary New Existing

APPLICATION TYPE: Construction Operation Modification

COMPANY NAME: Harris Semiconductor COUNTY: Brevard

Identify the specific emission point source(s) addressed in this application (i.e. Lime Kiln No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired) B-59 Manufacturing Fab

SOURCE LOCATION: Street Palm Bay Road City Palm Bay

UTM: East 17-538700 North 17-3100900

Latitude 28° 01' 20"N Longitude 80° 36' 10"W

APPLICANT NAME AND TITLE: J. R. Kolanek, Manager Environmental Services

APPLICANT ADDRESS: P.O. Box 883, Melbourne, Florida 32901

SECTION I: STATEMENTS BY APPLICANT AND ENGINEER

A. APPLICANT

I am the undersigned owner or authorized representative* of Harris Semiconductor

I certify that the statements made in this application for a modified permit are true, correct and complete to the best of my knowledge and belief. Further, I agree to maintain and operate the pollution control source and pollution control facilities in such a manner as to comply with the provision of Chapter 403, Florida Statutes, and all the rules and regulations of the department and revisions thereof. I also understand that a permit, if granted by the department, will be non-transferable and I will promptly notify the department upon sale or legal transfer of the permitted establishment.

*Attach letter of authorization

Signed: James R. Kolanek

J. R. Kolanek, Manager, Environmental Services
Name and Title (Please Type)

Date: 5/18/88 Telephone No. (407) 724-7467

B. PROFESSIONAL ENGINEER REGISTERED IN FLORIDA (where required by Chapter 471, F.S.)

This is to certify that the engineering features of this pollution control project have been designed/examined by me and found to be in conformity with modern engineering principles applicable to the treatment and disposal of pollutants characterized in the permit application. There is reasonable assurance, in my professional judgment, that

See Florida Administrative Code Rule 17-2.100(57) and (104)

the pollution control facilities, when properly maintained and operated, will discharge an effluent that complies with all applicable statutes of the State of Florida and the rules and regulations of the department. It is also agreed that the undersigned will furnish, if authorized by the owner, the applicant a set of instructions for the proper maintenance and operation of the pollution control facilities and, if applicable, pollution sources.

Signed Lawrence R. Hutker

Lawrence R. Hutker
Name (Please Type)

Harris Semiconductor
Company Name (Please Type)

P.O. Box 883, Melbourne, Florida 32901
Mailing Address (Please Type)

Florida Registration No. 35972 Date: 5/18/88 Telephone No. (407) 729-4655

SECTION II: GENERAL PROJECT INFORMATION

Describe the nature and extent of the project. Refer to pollution control equipment, and expected improvements in source performance as a result of installation. State whether the project will result in full compliance. Attach additional sheet if necessary.

This is a modification and consolidation of existing air permits.

3. Schedule of project covered in this application (Construction Permit Application Only)

Start of Construction N/A Completion of Construction N/A

4. Costs of pollution control system(s): (Note: Show breakdown of estimated costs only for individual components/units of the project serving pollution control purposes. Information on actual costs shall be furnished with the application for operation permit.)

N/A

5. Indicate any previous DER permits, orders and notices associated with the emission point, including permit issuance and expiration dates.

AO 05-121924 issued 9/17/86; expires 9/14/91

AC 05-104515 issued 1/15/86; expires 6/30/86

E. Requested permitted equipment operating time: hrs/day 24; days/wk 7; wks/yr 52;
if power plant, hrs/yr _____; if seasonal, describe: _____

F. If this is a new source or major modification, answer the following questions.
(Yes or No)

1. Is this source in a non-attainment area for a particular pollutant? No
 - a. If yes, has "offset" been applied? _____
 - b. If yes, has "Lowest Achievable Emission Rate" been applied? _____
 - c. If yes, list non-attainment pollutants. _____
2. Does best available control technology (BACT) apply to this source? No
If yes, see Section VI.
3. Does the State "Prevention of Significant Deterioration" (PSD) requirement apply to this source? If yes, see Sections VI and VII. No
4. Do "Standards of Performance for New Stationary Sources" (NSPS) apply to this source? No
5. Do "National Emission Standards for Hazardous Air Pollutants" (NESHAP) apply to this source? No

H. Do "Reasonably Available Control Technology" (RACT) requirements apply to this source? No

a. If yes, for what pollutants? _____

b. If yes, in addition to the information required in this form, any information requested in Rule 17-2.650 must be submitted.

Attach all supportive information related to any answer of "Yes". Attach any justification for any answer of "No" that might be considered questionable.

SECTION III: AIR POLLUTION SOURCES & CONTROL DEVICES (Other than Incinerators)

A. Raw Materials and Chemicals Used in your Process, if applicable:

Description	Contaminants		Utilization Rate - lbs/hr	Relate to Flow Diagram
	Type	% Wt		
---SEE ATTACHMENT C ---				

B. Process Rate, if applicable: (See Section V, Item 1)

1. Total Process Input Rate (lbs/hr): not applicable

2. Product Weight (lbs/hr): not applicable

C. Airborne Contaminants Emitted: (Information in this table must be submitted for each emission point, use additional sheets as necessary)

Name of Contaminant	Emission ¹		Allowed Emission Rate per Rule 17-2	Allowable ³ Emission lbs/hr	Potential ⁴ Emission		Relate to Flow Diagram
	Maximum lbs/hr	Actual T/yr			lbs/yr	T/yr	
---SEE ATTACHMENT B ---							

¹See Section V, Item 2.

²Reference applicable emission standards and units (e.g. Rule 17-2.600(5)(b)2. Table II, E. (1) - 0.1 pounds per million BTU heat input)

³Calculated from operating rate and applicable standard.

⁴Emission, if source operated without control (See Section V, Item 3).

J. Control Devices: (See Section V, Item 4)

Name and Type (Model & Serial No.)	Contaminant	Efficiency	Range of Particles Size Collected (in microns) (If applicable)	Basis for Efficiency (Section V Item 5)
---SEE ATTACHMENT D ---				

E. Fuels

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	avg/hr	max./hr	

*Units: Natural Gas--MMCF/hr; Fuel Oils--gallons/hr; Coal, wood, refuse, other--lbs/hr.

Fuel Analysis:

Percent Sulfur: _____ Percent Ash: _____

Density: _____ lbs/gal Typical Percent Nitrogen: _____

Heat Capacity: _____ BTU/lb _____ BTU/gal

Other Fuel Contaminants (which may cause air pollution): _____

F. If applicable, indicate the percent of fuel used for space heating.

Annual Average _____ Maximum _____

G. Indicate liquid or solid wastes generated and method of disposal.

Waste water from air scrubbers is discharged to on-site Waste Water Treatment

Plant--discharge to deepwell under UIC - Permit #UC05-126519.

-----SEE ATTACHMENT D-----

H. Emission Stack Geometry and Flow Characteristics (Provide data for each stack):

Stack Height: _____ ft. Stack Diameter: _____ ft.
 Gas Flow Rate: _____ ACFM _____ DSCFM Gas Exit Temperature: _____ °F.
 Water Vapor Contents: _____ % Velocity: _____ FPS

SECTION IV: INCINERATOR INFORMATION

not applicable

Type of Waste	Type 0 (Plastics)	Type I (Rubbish)	Type II (Refuse)	Type III (Garbage)	Type IV (Pathological)	Type V (Liq. & Gas By-prod.)	Type VI (Solid By-prod.)
Actual lb/hr Incinerated							
Uncontrolled (lbs/hr)							

Description of Waste _____

Total Weight Incinerated (lbs/hr) _____ Design Capacity (lbs/hr) _____

Approximate Number of Hours of Operation per day _____ day/wk _____ wks/yr. _____

Manufacturer _____

Date Constructed _____ Model No. _____

	Volume (ft) ³	Heat Release (BTU/hr)	Fuel		Temperature (°F)
			Type	BTU/hr	
Primary Chamber					
Secondary Chamber					

Stack Height: _____ ft. Stack Diameter: _____ Stack Temp. _____

Gas Flow Rate: _____ ACFM _____ DSCFM* Velocity: _____ FPS

*If 50 or more tons per day design capacity, submit the emissions rate in grains per standard cubic foot dry gas corrected to 50% excess air.

Type of pollution control device: Cyclone Wet Scrubber Afterburner
 Other (specify) _____

Brief description of operating characteristics of control devices: _____

Ultimate disposal of any effluent other than that emitted from the stack (scrubber water, ash, etc.):

NOTE: Items 2, 3, 4, 6, 7, 8, and 10 in Section V must be included where applicable.

SECTION V: SUPPLEMENTAL REQUIREMENTS

Please provide the following supplements where required for this application.

1. Total process input rate and product weight -- show derivation [Rule 17-2.100(127)]
2. To a construction application, attach basis of emission estimate (e.g., design calculations, design drawings, pertinent manufacturer's test data, etc.) and attach proposed methods (e.g., FR Part 60 Methods 1, 2, 3, 4, 5) to show proof of compliance with applicable standards. To an operation application, attach test results or methods used to show proof of compliance. Information provided when applying for an operation permit from a construction permit shall be indicative of the time at which the test was made.
3. Attach basis of potential discharge (e.g., emission factor, that is, AP42 test).
4. With construction permit application, include design details for all air pollution control systems (e.g., for baghouse include cloth to air ratio; for scrubber include cross-section sketch, design pressure drop, etc.)
5. With construction permit application, attach derivation of control device(s) efficiency. Include test or design data. Items 2, 3 and 5 should be consistent: actual emissions = potential (1-efficiency).
6. An 8 1/2" x 11" flow diagram which will, without revealing trade secrets, identify the individual operations and/or processes. Indicate where raw materials enter, where solid and liquid waste exit, where gaseous emissions and/or airborne particles are evolved and where finished products are obtained.
7. An 8 1/2" x 11" plot plan showing the location of the establishment, and points of airborne emissions, in relation to the surrounding area, residences and other permanent structures and roadways (Example: Copy of relevant portion of USGS topographic map).
8. An 8 1/2" x 11" plot plan of facility showing the location of manufacturing processes and outlets for airborne emissions. Relate all flows to the flow diagram.

9. The appropriate application fee in accordance with Rule 17-4.05. The check should be made payable to the Department of Environmental Regulation.
10. With an application for operation permit, attach a Certificate of Completion of Construction indicating that the source was constructed as shown in the construction permit.

SECTION VI: BEST AVAILABLE CONTROL TECHNOLOGY

A. Are standards of performance for new stationary sources pursuant to 40 C.F.R. Part 60 applicable to the source?

Yes No

Contaminant	Rate or Concentration

B. Has EPA declared the best available control technology for this class of sources (if yes, attach copy)

Yes No

Contaminant	Rate or Concentration

C. What emission levels do you propose as best available control technology?

Contaminant	Rate or Concentration

D. Describe the existing control and treatment technology (if any).

- | | |
|---------------------------|--------------------------|
| 1. Control Device/System: | 2. Operating Principles: |
| 3. Efficiency:* | 4. Capital Costs: |

*Explain method of determining

5. Useful Life:

6. Operating Costs:

7. Energy:

8. Maintenance Cost:

9. Emissions:

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

10. Stack Parameters

a. Height: ft. b. Diameter: ft.

c. Flow Rate: ACFM d. Temperature: °F.

e. Velocity: FPS

E. Describe the control and treatment technology available (As many types as applicable, use additional pages if necessary).

1.

a. Control Device: b. Operating Principles:

c. Efficiency:¹ d. Capital Cost:

e. Useful Life: f. Operating Cost:

g. Energy:² h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

2.

a. Control Device: b. Operating Principles:

c. Efficiency:¹ d. Capital Cost:

e. Useful Life: f. Operating Cost:

g. Energy:² h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

¹Explain method of determining efficiency.

²Energy to be reported in units of electrical power - KWH design rate.

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

3.

a. Control Device:

b. Operating Principles:

c. Efficiency:¹

d. Capital Cost:

e. Useful Life:

f. Operating Cost:

g. Energy:²

h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

4.

a. Control Device:

b. Operating Principles:

c. Efficiency:¹

d. Capital Costs:

e. Useful Life:

f. Operating Cost:

g. Energy:²

h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

F. Describe the control technology selected:

1. Control Device:

2. Efficiency:¹

3. Capital Cost:

4. Useful Life:

5. Operating Cost:

6. Energy:²

7. Maintenance Cost:

8. Manufacturer:

9. Other locations where employed on similar processes:

a. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

* Explain method of determining efficiency.

Energy to be reported in units of electrical power - KWH design rate.

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

(8) Process Rate:¹

b. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

(8) Process Rate:¹

10. Reason for selection and description of systems:

¹Applicant must provide this information when available. Should this information not be available, applicant must state the reason(s) why.

SECTION VII - PREVENTION OF SIGNIFICANT DETERIORATION

A. Company Monitored Data

1. _____ no. sites _____ TSP _____ () SO₂* _____ Wind spd/dir

Period of Monitoring _____ / _____ / _____ to _____ / _____ / _____
month day year month day year

Other data recorded _____

Attach all data or statistical summaries to this application.

Specify bubbler (B) or continuous (C).

HARRIS SEMICONDUCTOR
AIR PERMIT - BUILDING 59
ATTACHMENT A
PROCESS DESCRIPTION

Attachment A

Building 59 houses a wafer fabrication facility on the second floor. The fabrication area employs a series of manufacturing procedures referred to as layering, patterning, doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

In the controlled environment of the fabrication clean room, wafer surfaces first undergo acid and/or solvent cleaning, followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process, the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "aligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques.

In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Fumes from the vapor deposition furnaces are oxidized in 'burn boxes.' The oxidized gases are then exhausted to scrubber systems. Additional material may be layered on the wafer surface in vapor and crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation.

Thirteen exhausted wet stations that house vats containing a variety of acid and caustic compounds are in the fabrication facility. Five of these stations contain solvents, one of which is heated.

The ground floor of the two-story manufacturing area houses a process equipment support room that contains gas cabinets, chemical storage cabinets, vacuum pumps and drains. These exhausted units service the process equipment which resides above it in the fabrication area. Storage cabinets safely hold virgin chemicals until they are ready for use. Gas cabinets house cylinders that supply process gases to the 'fab' operations. In addition, several waste collection areas are exhausted. The ground floor also houses the site's distilled water plant, and a mechanical equipment storage area.

The exhaust system for the building is divided between two scrubbers. Acid vapors are vented to scrubber number F59S01, while solvent exhaust streams are ducted to scrubber number F59S03. Both systems reside on the site grounds directly outside the west wall of the building. (See site plan and scrubber location maps attached.)

HARRIS SEMICONDUCTOR
AIR PERMIT - BUILDING 59

ATTACHMENT B
AIR EMISSIONS

Attachment B

Monitoring work was performed on the building 59 solvent scrubber system in December of 1986. The test conducted to establish VOC emissions from the fab was EPA method 25A (flame ionization detector.)

The test results initially revealed that total accumulative monitored VOC emissions for the building were 0.37 tons/year expressed as propane. Building 59 houses the site's newest and most technologically sophisticated clean room. Due to increased customer interest in the products manufactured in this building, production schedules are likely to vary. In order to accomodate these fluctuations, total VOC emissions were adjusted to represent maximum loading. Hence, an 8760 hour a year production schedule was utilized to calculate emissions, and the loading was estimated to be 0.50 tons/year. Fluctuations in production schedules are common at Semiconductor, because manufacturing hours depend on product demand. The following assumptions was made regarding monitoring work on this building:

-VOC values refer to all organic emissions including organic solvents, as defined in the Florida Environmental Regulations.

Total projected VOC emissions for building 59 is 0.57 tons/year. This number is representative of maximum VOC emissions, and is an extrapolation of the building's monitored emission rate mentioned above. The site's projected VOC limit is 150 tons/year.

No monitoring work to estimate acid emissions has been performed to date. Scrubber removal efficiencies as prescribed by the scrubber manufacturer (Beverly Pacific Corporation) are provided in this attachment. Semiconductor's Environmental Services Department plans to verify these acid removal efficiencies sometime within the calendar year.

EPA METHOD 25-A (F.I.D. ANALYSIS) BUILDING 59
 VOC EMISSIONS DURING PRODUCTION HOURS

TEST DATE	SCRUBBER #	VOC EMISSIONS (TON/YR)
12/09/86	F59S03	0.50

NOTE: ABOVE BASED ON ACTUAL OPERATING HOURS.

TOTAL VOC EMISSIONS FROM BUILDING 59
 AS DETECTED BY EPA METHOD 25-A

SCRUB#	PRODUCTN SCHEDULE	NONPRODUCTN SCHEDULE	PRODUCTN EMISSIONS (TON/YR)	NONPRODUCTN EMISSIONS (TON/YR)	TOTAL VOC EMISSIONS (TON/YR)
F59S03	8760	0	0.50	0	0.50

TOTAL PROJECTED VOC EMISSIONS FOR BLDG 59 = 0.57 TONS/YEAR



Divisions . . . Beverly Mech. Contracting
Industrial Systems
Process Equipment
Refrigeration Service

BEVERLY PACIFIC CORP.

140 W. Providencia Ave., Burbank, CA 91502 • St. Contr. Lic. No. 158846 • Tele. No. 874209 • (818) 841-1400

TABLE OF SCRUBBER EFFICIENCIES/CONTAMINANTS

Information given below is to be used as a guide only

<u>CONTAMINANTS</u>	<u>TYPE (SEE NOTE A)</u>	<u>BPE APPROX. EFFICIENCY</u>
Acetic Acid (CH ₃ CO ₂ H)	G & L	95.7%
Acetone (CH ₃ COCH ₃)	G	95%
Aluminum Bright Dip	G & L	40-65%
(2) Amines (RNH ₂)	G	98-99%
(2) Ammonia (NH ₂)	G	97-99%
Ammonia Hydroxide (NH ₄ OH)	L	97-99%
Ammonia Nitrate (NH ₄ NO ₃)	S & SS	98-99%
Asodizing Solutions	L	99%
Boric Acid (H ₃ BO ₃)	L	95-98%
(1) Bromine (BR ₂)	G	99%
(1) Carbon Dioxide (CO ₂)	G	80-90%
Caustic (NaOH)	L	99%
(1) Chlorine (Cl ₂)	G	99%
(3) Chlorine Dioxide (ClO ₂)	G	95-98%
Chromic Acid (H ₂ CrO ₄)	L	99%
Citric Acid	L	98-99%
Cyanide Salts	L	99%
Ethanol (CH ₃ CH ₂ OH)	G & L	99%
(1) Formaldehyde (FCHO)	G & L	98-99%
Formic Acid (HCO ₂ H)	G	98-99%
Hydrobromic Acid (HBr)	G & L	98-99%
Hydrochloric Acid (HCl)	G, L & SL	95-99%

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 Divisions ... Beverly Mech. Contracting
 Industrial Systems
 Process Equipment
 Refrigeration Service


BEVERLY PACIFIC CORP.

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Hydrofluoric Acid (HF)	G	95-97%
Hydrogen Cyanide (HCN)	G	99%
Hydrogen Peroxide	G	95%
Hydrogen Sulfide (H ₂ S)	G	99%
(3) Mercaptans (RSH)	G & L	98-99%
Methanol (CH ₃ OH)	G	97.5%
Nitric Acid (HNO ₃)	L	95%
(1) Nitrogen Oxides (NO _x)	G	30-40%
Oil Mists	L & SL	95-98%
Perchloric Acid	G	98-99%
Phenol (C ₆ H ₅ OH)	G & L	95-99%
Phosphate Salt Baths	L	98-99%+
Phosphoric Acid (H ₃ PO ₄)	L	98-99%+
Silicon Tetrachloride (SiCl ₄)	G	99%
Silicon Tetrafluoride (SiF ₄)	G	99%
Sodium Chloride (NaCl)	S & L	98-99%+
Sulfuric Acid (H ₂ SO ₄)	L	95%
(1) Sulfur Dioxide (SO ₂)	G	87-90%
Urea (H ₂ NCONH ₂)	S & SS	98-99%
(1) Hydrogen Sulfide (H ₂ S)	G	98-99%
Xylene	L	95%



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Note A: G = Gas
L = Liquid particulate
above 3 microns
SL = Liquid particulate
below 3 microns

S = Solid particulate
above 3 microns
SS = Solid particulate
below 3 microns

Notes:
(1) NaOH Scrubbing liquid
required
(2) H2SO4 scrubbing liquid
may be required
(3) Special scrubbing liquid
required
Consult BPC for
recommendation
4. Consult BPC if
efficiencies other than
shown are required or
for contams. not shown

HARRIS SEMICONDUCTOR

AIR PERMIT - BUILDING 59

ATTACHMENT C

RAW MATERIALS AND CHEMICALS

HARRIS SEMICONDUCTOR
BUILDING 59 CONSOLIDATED AIR PERMIT
PROCESS GASSES

- 1 ARGON
- 2 BORON TRIBROMIDE
- 3 BORON TRIFLUORIDE
- 4 CHLORINE
- 5 DICHLOROSILANE
- 6 HELIUM
- 7 HYDROGEN
- 8 HYDROGEN CHLORIDE
- 9 NITROGEN
- 10 NITROGEN TRIFLUORIDE
- 11 NITROUS OXIDE
- 12 OXYGEN
- 13 OZONE
- 14 PHOSPHINE
- 15 PHOSPHOROUS OXYCHLORIDE
- 16 SILANE
- 17 SULFUR HEXAFLUORIDE
- 18 TRIMETHYL BORATE
- 19 TRIMETHYL PHOSPHATE
- 20 TUNGSTON HEXAFLUORIDE
- 21 HEXAFLUOROETHANE

JUNE 8, 1988

HARRIS SEMICONDUCTOR
BUILDING 59 CONSOLIDATED AIR PERMIT
PROCESS SOLVENTS

- 1 ACETONE
- 2 CARBON TETRACHLORIDE
- 3 1,1,1 TRICHLOROETHANE
- 4 FREON TF
- 5 FREON TMS
- 6 N-BUTYL ALCOHOL
- 7 METHANOL
- 8 BUTYL CELLOSOLVE
- 9 2-ETHOXYETHYL ACETATE
- 10 CELLOSOLVE ACETATE
- 11 DICHLORODIFLUOROETHANE
- 12 EDTA
- 13 ETHYL ALCOHOL
- 14 ETHYL BENZENE
- 15 ISOPROPYL ALCOHOL
- 16 METHYLPHENYL ETHER
- 17 MONOETHANOLAMINE
- 18 N-BUTYL ACETATE
- 19 TOLUENE
- 20 XYLENE
- 21 TRICHLOROTRIFLUOROETHANE
- 22 N-METHYL PYRROLIDONE
- 23 METHYL-2-PYRROLIDINONE
- 24 PROPYLENE GLYCOL 1,2 PROPANEDIOL

JUNE 8, 1988

HARRIS SEMICONDUCTOR
BUILDING 59 CONSOLIDATED AIR PERMIT
PROCESS CHEMICALS

- 1 AMMONIA
- 2 AMMONIUM FLUORIDE
- 3 AMMONIUM HYDROXIDE
- 4 ETHYLENE GLYCOL
- 5 GLYCERINE
- 6 HYDROCHLORIC ACID
- 7 HYDROFLUORIC ACID
- 8 HYDROGEN PEROXIDE
- 9 MOLYBDENUM DISULFIDE
- 10 NITRIC ACID
- 11 OIL
- 12 PHOSPHORIC ACID
- 13 POTASSIUM DICHROMATE
- 14 POTASSIUM PHOSPHATE
- 15 RED PHOSPHOROUS
- 16 SODIUM CARBONATE
- 17 SODIUM HYDROXIDE
- 18 SODIUM PHOSPHATE
- 19 SULFURIC ACID
- 20 TETRAMETHYL AMMONIUM HYDROXIDE
- 21 TRISODIUM PHOSPHITE

JUNE 8, 1988

*HARRIS SEMICONDUCTOR
AIR PERMIT - BUILDING 59*

*ATTACHMENT D
CONTROL EQUIPMENT*

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 59 DATE ISSUED : 09/17/86
PERMIT NUMBER: AD 05-121924 RENEWAL DATE: 07/16/91
PERMIT TYPE : OPERATING DATE EXPIRES: 09/14/91

AREA SERVED:
PROCESS DESCRIPTION: ACID VAPOR SCRUBBER

PERMIT LIMITS

VOL. RATE (SCFM): 40,000
ACID MIST (LB/HR): 0.0079
SOLVENTS (LB/HR): --
VOCs (LB/HR): --
OPER. (HRS/YEAR): 2112

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/01
NOTIFICATION OF VE TEST : 10/26
ANNUAL VIS EMISSION TEST: 11/10

EQUIPMENT INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-40HT
LOCATION : B59 GROUND WEST SIDE
HARRIS ID NUMBER : F59S01 STACK HEIGHT (FT): 35
VOLUME FLOW RATE (CFM): 40,000 STACK DIAMETER (IN): 44
RECIRCULATION RATE (GPM): 175 STACK VELOCITY (FPM):
MAKEUP WATER RATE (GPM): 17.5 DUCT MATERIAL : polypro

PERMIT HISTORY

PERMIT NUMBER: AC 05-54991
DATE EXPIRED : 06/01/84

PERMIT NUMBER: AC 05-104516
DATE EXPIRED : 06/30/86

PERMIT NUMBER:
DATE EXPIRED :

SCRUBBER INFORMATION

HARRIS ID # : F59S01
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-40HT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : HORIZONTAL CROSS FLOW, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR, DWG. F-600-1

DESIGN DATA

VOLUME FLOW RATE (CFM): 40,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 175 MAKE UP RATE (GPM): 17.5

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE:
RECIRCULATION RATE (GPM): 90 MAKE UP RATE (GPM): 2.5 DATE: 01/16/87

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP INC MODEL NUMBER : 36E188-105
SERIAL NUMBER: F1280 HP : 3 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5912

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-49
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD CURVED BLADES,
DWG. F-600-1

DESIGN DATA

VOLUME FLOW RATE (CFM): 33,384 STATIC PRESS (IN): 5.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): 764 DATE: SUBMITTAL
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : RPM :
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5913

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 59 DATE ISSUED : 01/15/86
PERMIT NUMBER: AC 05-104515 RENEWAL DATE: 04/01/86
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 06/30/86

AREA SERVED:
PROCESS DESCRIPTION: VOC/SOLVENT SCRUBBER

PERMIT LIMITS

VOL. RATE (SCFM): 20,000
ACID MIST (LB/HR): --
SOLVENTS (LB/HR): 0.0018
VOCs (LB/HR): --
OPER. (HRS/YEAR): 2112

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT :
NOTIFICATION OF VE TEST :
ANNUAL VIS EMISSION TEST:

EQUIPMENT INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-24UT
LOCATION : B59 GROUND WEST SIDE
HARRIS ID NUMBER : F59S03 STACK HEIGHT (FT): 35
VOLUME FLOW RATE (CFM): 24,000 STACK DIAMETER (IN): 42
RECIRCULATION RATE (GPM): 105 STACK VELOCITY (FPM):
MAKEUP WATER RATE (GPM): 10.5 DUCT MATERIAL : galv.

PERMIT HISTORY

PERMIT NUMBER: AC 05-54990
DATE EXPIRED : 06/01/84

PERMIT NUMBER: AC 05-104515
DATE EXPIRED : 06/30/86

PERMIT NUMBER:
DATE EXPIRED :

SCRUBBER INFORMATION

HARRIS ID # : F59503
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-24VT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : VERTICAL COUNTER-CURRENT, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR, DWG. F-600-2

DESIGN DATA

VOLUME FLOW RATE (CFM): 24,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 105 MAKE UP RATE (GPM): 10.5

ACTUAL DATA

VOLUME FLOW RATE (CFM): 5,494 PRESSURE DROP (IN): N/E DATE: 12/09/86
RECIRCULATION RATE (GPM): 30 MAKE UP RATE (GPM): 2.5 DATE: 01/16/87

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP IND MODEL NUMBER : 36E188-105
SERIAL NUMBER: F1280 HP : 3 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5912

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-36
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD CURVED BLADES,
DWG. F-600-2

DESIGN DATA

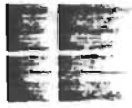
VOLUME FLOW RATE (CFM): 16,000 STATIC PRESS (IN): 6.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 5,494 SPEED (RPM): 1094 DATE: SUBMITTAL
STATIC PRESS (IN): DATE: 12/09/86

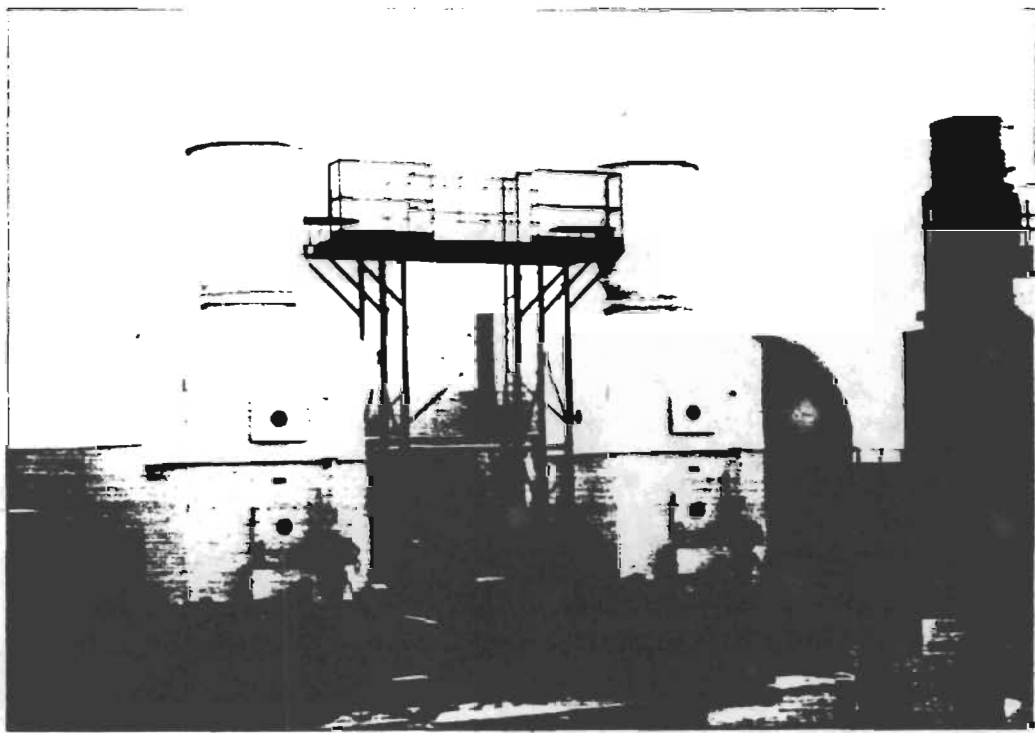
FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : RPM :
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5913



BEVERLY PACIFIC CORPORATION

SCRUBBERS

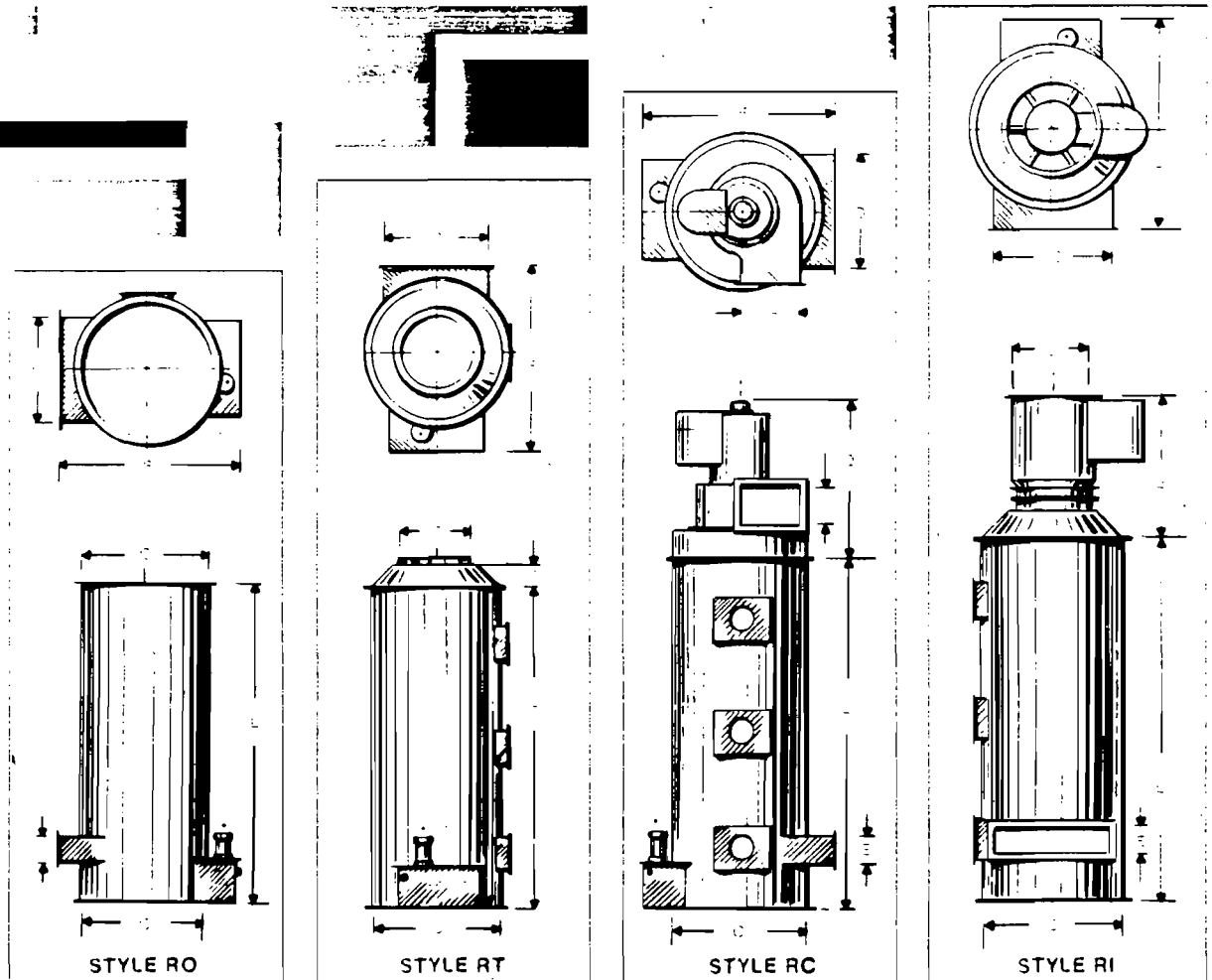


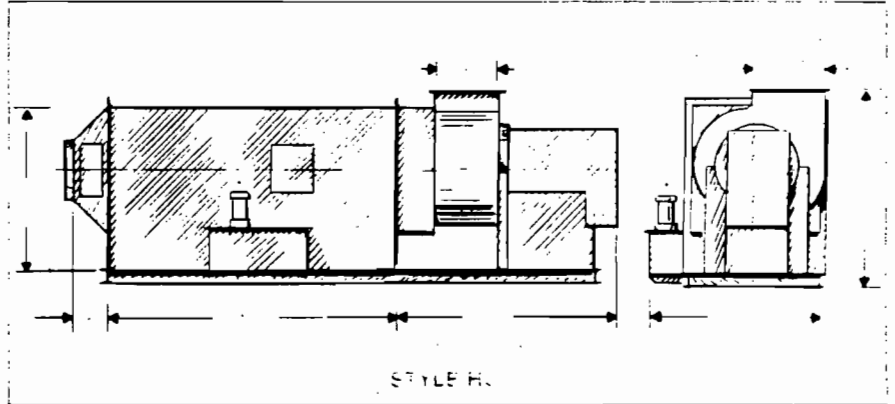
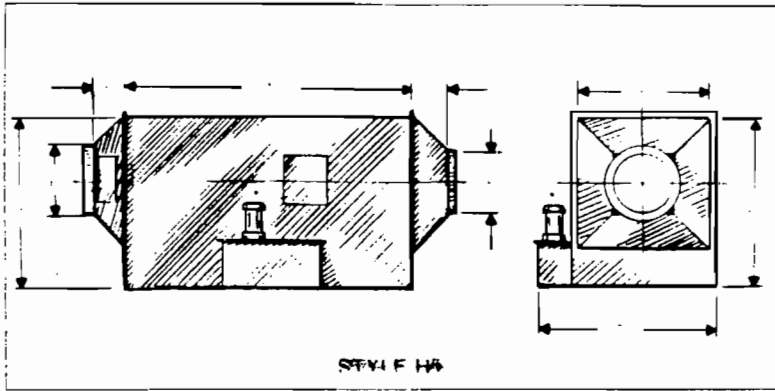
FIBERGLASS REINFORCED PLASTIC

PACKED SCRUBBER DIMENSIONAL CHART

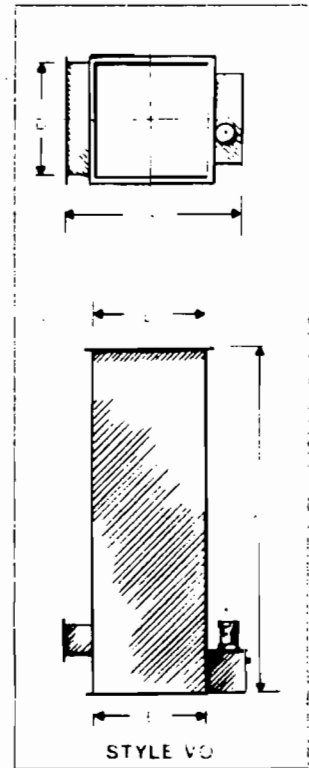
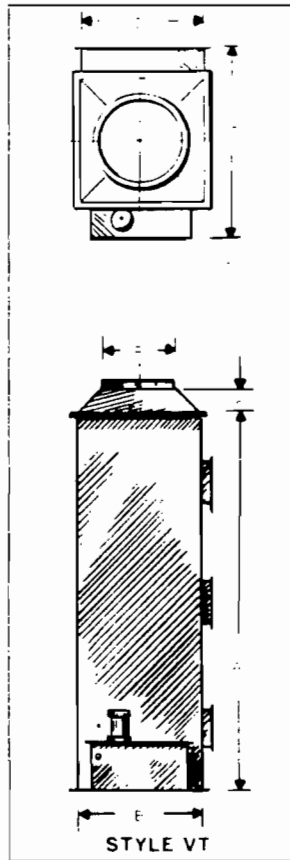
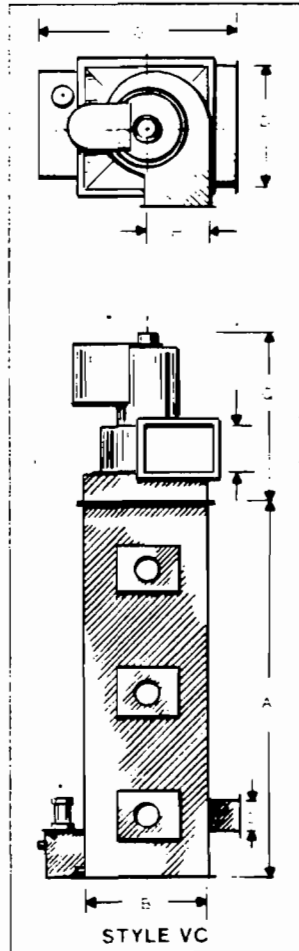
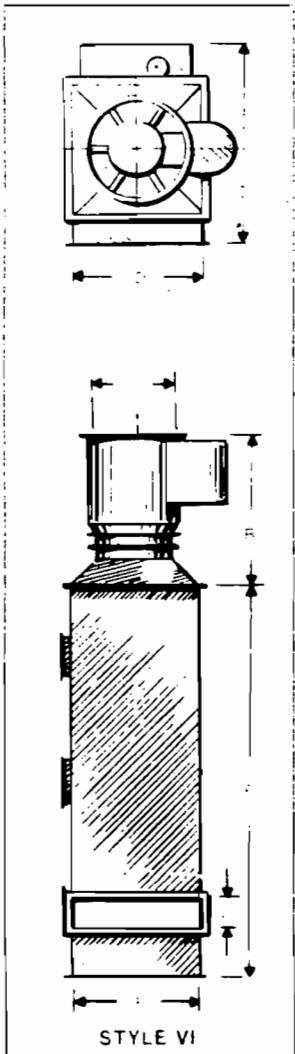
MODEL NUMBERS
DIMENSIONS IN INCHES

	PS-2	PS-4	PS-6	PS-8	PS-12	PS-18	PS-24	PS-30	PS-40	PS-50
A	78	82	84	94	101	108	112	114	128	118
B	24	36	42	48	60	72	84	96	108	120
C	28	40	48	58	72	84	96	108	120	136
D	22	34	40	46	58	70	80	92	104	116
E	6	8	10	11	12	16	18	20	24	24
F	46	58	66	76	90	102	114	126	138	154
G	42	54	60	66	78	90	102	114	126	138
H	13 $\frac{3}{4}$	16 $\frac{3}{4}$	22 $\frac{1}{2}$	26 $\frac{1}{4}$	29 $\frac{1}{2}$	35 $\frac{1}{4}$	39	47 $\frac{1}{4}$	52 $\frac{3}{4}$	63 $\frac{3}{4}$
I	10 $\frac{3}{4}$	12 $\frac{3}{4}$	17	20 $\frac{1}{2}$	22 $\frac{3}{4}$	27	30	37 $\frac{1}{2}$	40 $\frac{3}{4}$	49 $\frac{3}{4}$
J	18	22	28	34	38	45	50	62	66	80
K	6	8	10	10	12	16	19	20	24	24
L	84	87	89	104	112	118	122	124	128	128
M	64	64	70	77	89	102	102	102	114	114
N	35	49	55	62	76	88	103	116	128	142
O	38	52	58	65	79	91	106	119	131	145
P	14	16	22	26	30	36	42	50	54	66
Q	45	50	61	64	68	72	78	86	93	103
R	35	44	55	65	75	85	94	108	120	141
S	46	52	59	69	72	79	82	97	100	110
T	36	48	54	60	72	84	96	108	120	132
WHEEL DIA.	12 $\frac{1}{4}$	15	20	24 $\frac{1}{2}$	27	33	36 $\frac{1}{2}$	44 $\frac{1}{2}$	49	60
CFM x 1000	1-2	2-4	4-6	6-8	8-12	12-18	18-24	24-30	40	40-50
RECIRC. GPM	7	15	25	35	45	75	105	135	175	225
MAKE-UP GPM	0.7	1.5	2.0	3.0	4.0	7.0	10.0	13.0	20	22.0
HT OP. WT.	388	745	1110	1570	2690	4085	5670	7595	990	16040
HT SHIP WT.	220	385	550	770	1210	1925	2750	3795	790	7040
VT OP. WT.	318	660	1060	1500	2630	3910	5470	7400	11650	15800
VT SHIP WT.	150	300	500	700	1150	1750	2550	3600	5250	6800





*May require one or more pumps.



COMPUTERIZED PACKING MEDIA SELECTION

The most common mistake made by scrubber manufacturers today is the use of only one type of packing media for all types of contaminant removal. Beverly Pacific Corporation scrubbers are designed with a computer program assist to determine the most beneficial packing media to achieve high removal efficiency coupled with low pressure drop providing the user with the ultimate in lower operating costs consistent with the contaminant removal requirements.

SCRUBBER CONFIGURATIONS

Beverly Pacific Corporation manufactures scrubbers of both crossflow and counter-current configurations.

The CROSSFLOW design is of low profile, rectangular shape wherein the contaminated air stream moves horizontally through the packing media and is scrubbed by the liquid flowing downward through the packing. This configuration is ideal for roof-top mounting and is available in ten (10) standard sizes with or without integral centrifugal fans.

The COUNTER-CURRENT design is offered in two (2) configurations, round or rectangular. While the round tower unit is the most economical in initial cost, the rectangular tower unit permits larger CFM volume using the same amount of floor space. In the counter-current design, the contaminated airstream flows up through the packing media and is scrubbed by the liquid flowing downward. The round and rectangular tower units are each offered in ten (10) sizes and are available with or without integral inline or centrifugal fans.

SCRUBBER MAKE-UP WATER CONSUMPTION

Beverly Pacific's scrubber design is based on a scrubbing liquid recirculation rate of 5 GPM per 1000 CFM of contaminated air. Of that 5 GPM, losses due to absorption and/or evaporation range from 0.2 GPM to 0.6 GPM, depending on inlet gas temperature and gas stream dust load.

ENTRAINMENT SEPARATION

The unique design of Beverly Pacific's mist eliminator section provides up to 99+^c% moisture particle entrapment at a pressure drop of approximately 0.5" W.G.

CONSTRUCTION

The structural housings are fabricated of Fiberglass Reinforced Plastic (FRP) materials which provide structural strength, are corrosion-resistant and light in weight. Resin selection depends on the corrosive element involved. Resins can also be of fire-retardant grade if required. Our construction technique employs the use of female molds resulting in an extremely smooth, attractive, gelcoated exterior surface (note the upper right photo on the facing page). Beverly Pacific Corporation's construction methods meet or exceed the requirements of NBS-PS 15-69 for custom contact-molded reinforced polyester chemical resistant process equipment.

OPTIONAL EQUIPMENT, FITTINGS AND ACCESSORIES

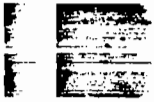
FITTINGS, such as drain, overflow, make-up water, access doors, etc. can usually be located to facilitate installation and maintenance.

RECIRCULATION RESERVOIR(S) are normally an integral part of the scrubber but, if required, can be furnished for remote installation.

RECIRCULATION PUMP(S) can be located within the built-in reservoir, but can also be installed in remote reservoir units.

SPECIAL RESERVOIR(S) can be furnished in applications where it is necessary to remove non-soluble particulate accumulation to prevent pump damage and minimize maintenance.

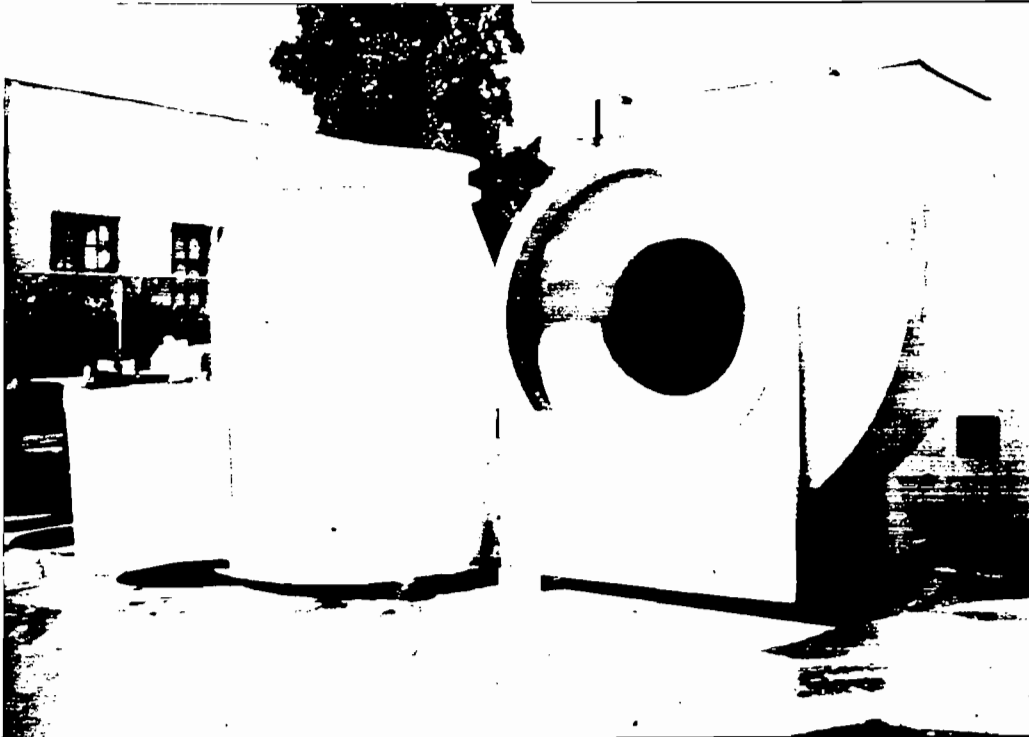
pH CONTROL SENSING/METERING equipment can be provided where contaminate absorption requires the addition of acid or caustic to the recirculated scrubbing liquid.



BEVERLY PACIFIC CORPORATION

Industrial Systems Division

EXHAUST FANS



FIBERGLASS REINFORCED PLASTIC

EXHAUST FAN INTRODUCTION

Beverly Pacific's complete line of centrifugal and inline exhaust fans have proven their reliability with years of successful, continuous corrosive service throughout the nation and around the world.

Our solid "FRP" construction defies corrosion and each is designed to provide smooth, quiet and maintenance-free operation . . . this superior combination permits peak performance with the lowest possible power consumption.

A wide selection of standard models, types and sizes are available to meet your specific requirements.

FAN WHEEL SUPERIORITY

The Beverly Pacific fan wheels are fabricated of corrosion-resistant Fiberglass Reinforced Plastic (FRP) materials. The fan wheel design is that of a "backward curve blade," Class II construction, and are available in standard sizes of 12 $\frac{1}{4}$ " through 66" diameters.

All of Beverly Pacific's fan wheels are both statically and dynamically balanced and run on a test stand prior to final assembly to insure continuous, vibration-free performance.

Every surface in contact with the air stream is corrosion resistant. The steel hub (providing the positive-lock connection to the drive shaft) is totally encapsulated in the wheel laminate and even the weight added during the wheel balancing process is corrosion resistant, Fiberglass Reinforced Plastic materials.

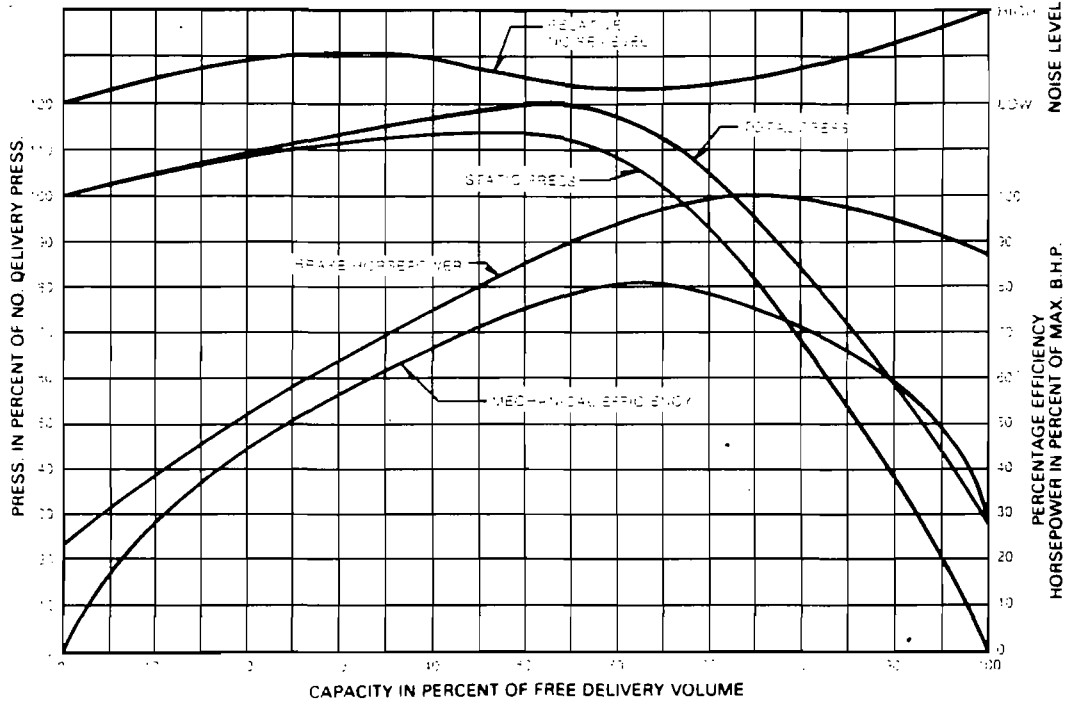
Should your particular requirement involve moving a volume of only a few hundred CFM at $\frac{1}{4}$ " S.P. or over 80,000 CFM at 6" S.P., Beverly Pacific has a proven standard size to meet your requirement.

EXHAUST FANS STANDARD AND OPTIONAL EQUIPMENT

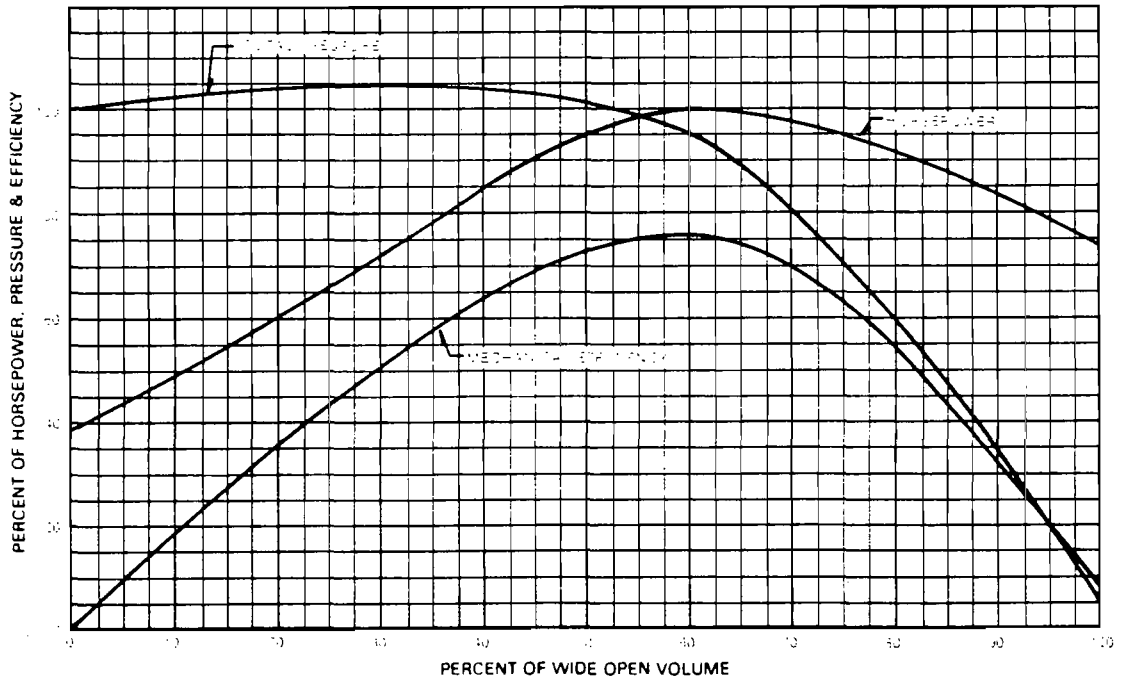
Standard Equipment: Beverly Pacific's centrifugal fans are equipped with a scroll bottom drain and flanged discharge outlet, and are furnished with a purchaser's choice of twelve (12) discharge outlet directions and a choice of right or left fan wheel rotation. Both of our fan styles, centrifugal and inline, are equipped with an OSHA approved belt guard and powered by 230-460/30/60 Hz motors . . . totally enclosed, fan-cooled, (TEFC) up to 20 horsepower, and Multi-guard motors are furnished when horsepower requirements are 25 or larger. Also, as standard equipment, Beverly Pacific furnishes the following list of first-line, top quality drive components which were selected based on motor horsepower, RPM, tip speed and weight of fan wheel, with a safety factor of 1.3 times the motor horsepower.

- a. BEARINGS — Beverly Pacific furnishes Dodge-Type K pillow blocks on the inline model. These Dodge bearings have Timken-tapered roller bearings, are fully self-aligning and designed to meet the stringent demands of power transmission. Based on radial and thrust load computations, bearing life expectancy is in excess of 100,000 hours.
- b. SHEAVES — Beverly Pacific Corporation furnishes Dodge sheaves, which are cast from the finest quality gray iron and machined to rigid quality control specifications. Groove design and spacing conforms to ASA, MPTA and RMA standards. These sheaves are equipped with Taper-Lock bushings, a superior mounting well recognized and widely used in industry.
- c. V-BELTS — Beverly Pacific furnishes Dodge Sealed-Life Belts, Type A, B and C which have a longer wearing protective cover, crowned top, concave sidewall, exceptional stability and an improved cord section which prevents failures caused by cord separation.
- d. WHEEL BACKING PLATES — Beverly Pacific uses Rex taper-lock, single-duty, Type B, steel sprocket, in the backing plate of all FRP fan wheels. This steel sprocket is completely embedded and encased with FRP materials to prevent corrosion attack.
- e. DRIVE SHAFTS — Beverly Pacific uses ground and polished, 1045 TGP shafting rounds, as produced by Inland Steel. This medium carbon steel is used because of its greater strength and hardness. The mechanical properties, based on $\frac{3}{4}$ " — $1\frac{1}{4}$ " diameter round bars of 1045, include a tensile strength of 98,000 PSI, yield strength of 59,000 PSI and a Brinell Hardness of 212.

BEVERLY PACIFIC CORPORATION CENTRIFUGAL FAN CHARACTERISTIC CURVE



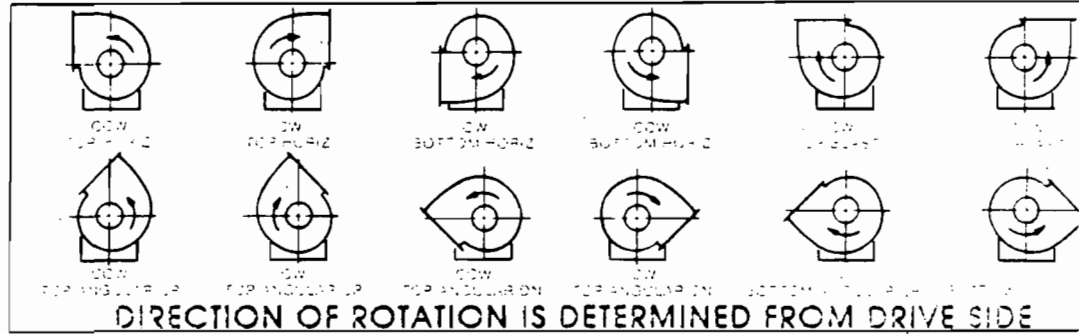
BEVERLY PACIFIC CORPORATION INLINE FAN CHARACTERISTIC CURVE



CENTRIFUGAL INDUSTRIAL EXHAUST FANS

	CB-12	CB-13	CB-15	CB-16	CB-18	CB-20	CB-22	CB-24	CB-27	CB-30	CB-33	CB-36
MID-RANGE CFM RECOMMENDED	2,150	2,625	3,200	3,900	4,750	5,800	7,075	8,650	10,550	12,875	15,700	19,000
FAN WHEEL DIAMETER	12¼	13½	15	16½	18¼	20	22¼	24½	27	30	33	36
A	13½	14½	16½	18¼	20	22	24½	26	29¼	32¼	36	40
B	10¾	11¾	12¾	14¾	15	17	18¾	20½	22¾	25	27	30
C	13¾	14¾	16¾	18¾	20	22½	24	26¾	29½	32	35¼	39
D	34¼	35¼	40¼	42¼	45	47¼	54	57¼	61½	64¼	66¾	69
E	22¼	22½	27¼	29¼	32¾	36½	39¼	43¼	49	53	58¼	65
F	15	16	18	19	20	23	26	28	30	33	36	39
G	11	11½	12½	14	15½	17¼	19	21½	23	25½	28½	31
H	13¾	14¾	15¾	17¾	18	21	22¾	24½	26¾	29	31	34
I	16	16	18¼	18¾	20	20½	23	23	25	26	26	28
J	3	3	4	4	4	4	6	6	6	6	6	6
K	9¼	10¼	11¼	12½	13½	15	16	18	20½	22	24	27
L	9¼	10¼	11¼	12½	13½	15	16	18	20½	22	24	27
M	3½	3¾	4¼	4½	5	5¼	6¾	6¾	7¾	8¼	9½	10
DRIVE SHAFT DIAMETER	1	1	1⅜	1⅜	1⅞	1⅞	1⅞	1⅞	1⅞	1⅞	1⅞	2
SHIPPING WEIGHT POUNDS	170	205	230	400	550	600	650	720	850	1,000	1,380	1,700

DESIGNATION OF DIRECTION OF ROTATION AND DISCHARGE



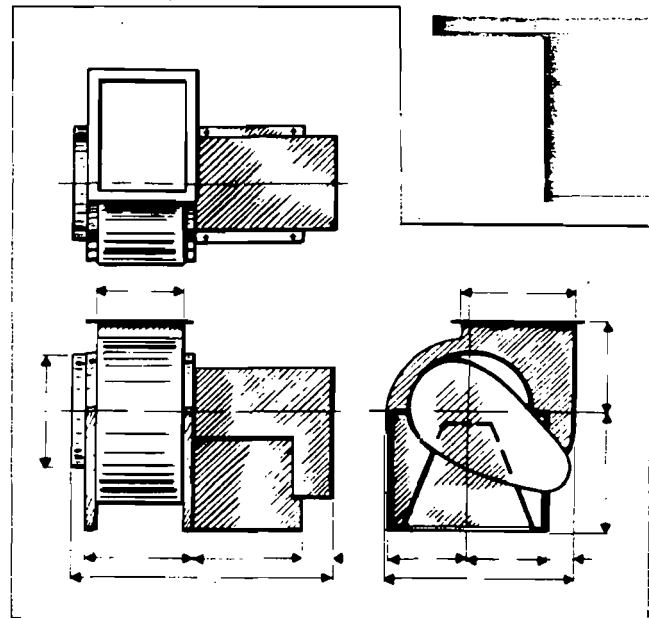
DIRECTION OF ROTATION IS DETERMINED FROM DRIVE SIDE

INLINE EXHAUST FANS

	IB-12	IB-15	IB-18	IB-20	IB-22	IB-24	IB-27	IB-30	IB-33	IB-36	IB-40	IB-44
MID-RANGE CFM RECOMMENDED	2,550	3,842	4,648	5,614	6,948	8,424	10,242	12,644	15,300	18,718	22,761	27,000
FAN WHEEL DIAMETER	12¼	15	18¼	20	22¼	24½	27	30	33	36½	40½	44
P	21"	28"	32½"	36½"	40"	47"	53"	55"	58"	63¼"	70"	76"
Q	14"	16"	20"	22"	24"	26"	30"	32"	36"	42"	46"	50"
R	18"	22"	26"	28"	32"	34"	38"	42"	45"	50"	56"	62"
S	2"	2"	2"	2"	2"	3"	3"	3"	3"	3"	3"	3"
T	23"	28"	31"	32"	34"	35"	37"	39"	40½"	45"	52"	60"
U	2"	2"	2"	2"	2"	3"	3"	3"	3"	3"	3"	3"
DRIVE SHAFT DIAMETER	1	1⅜	1⅜	1⅜	1⅞	1⅞	1⅞	1⅞	1⅞	2⅜	2⅜	2⅞
SHIPPING WEIGHT POUNDS	90	130	290	320	350	380	450	525	730	850	1,110	1,400

DIMENSIONAL CHART

CB-36	CB-40	CB-44	CB-48	CB-54	CB-60	CB-66	
9,150	23,375	28,525	34,775	42,450	51,775	63,175	MID-RANGE CFM RECOMMENDED
16½	40¼	44½	49	54¼	60	66	FAN WHEEL DIAMETER
10	44½	49	54	60	66	72	A
10	34½	37½	40½	44¼	49¼	54¼	B
19	43	47¼	52	57½	63½	70¼	C
39¼	79¾	84¼	88½	93	97¾	104¾	D
55¼	72½	79½	88	97	108	119	E
11½	42	49¼	49	54	59	64	F
10½	34½	37½	41	46	50½	55	G
14	40½	43½	48	50¼	53¼	60¼	H
26	27½	29½	29	31¼	33	33	I
3	8	8	8	8	8	8	J
27	25¾	26¼	30	34	37	40	K
27	25¾	26¼	30	34	37	40	L
0¼	11¼	12¼	14	15½	17½	19½	M
2¾	2¾	2¾	2¾	2½	2½	2½	DRIVE SHAFT DIAMETER
610	2,050	2,300	2,600	3,110	3,525	4,000	SHIPPING WEIGHT POUNDS



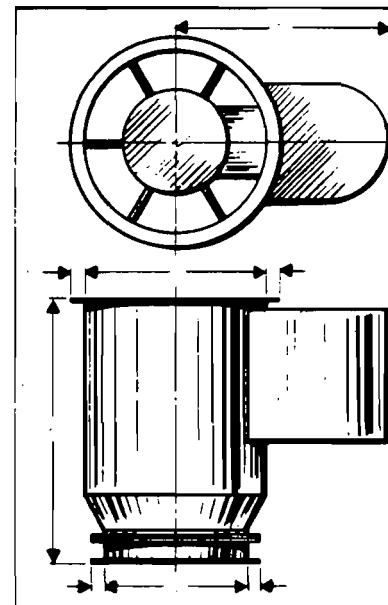
Bevel, Paco, ERP constructed fans have a Type "A" classification for spark resistance.

STANDARD CLASSIFICATIONS FOR SPARK RESISTANT CONSTRUCTION

TYPE	CONSTRUCTION
A	All parts of the fan in contact with the air or gas being handled shall be made of non-ferrous material.
B	The fan shall have an entirely non-ferrous wheel and non-ferrous ring about the opening through which the shaft passes.
C	The fan shall be so constructed that a shift of the wheel or shaft will not permit two ferrous parts of the fan to rub or strike.

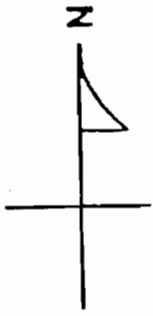
DIMENSIONAL CHART

IB-44	IB-49	IB-54	IB-60	IB-66	
7,822	33,733	41,349	50,579	61,201	MID-RANGE CFM RECOMMENDED
4½	49	54¼	60	66	FAN WHEEL DIAMETER
8"	84"	93"	104"	116"	P
7"	54"	60"	66"	72"	Q
2"	66"	72"	80"	88"	R
	3"	3"	3"	3"	S
3"	65"	68"	72"	76"	T
	3"	3"	3"	3"	U
¼	2¾	2½	2½	2½	DRIVE SHAFT DIAMETER
250	1,420	1,650	1,800	2,100	SHIPPING WEIGHT POUNDS



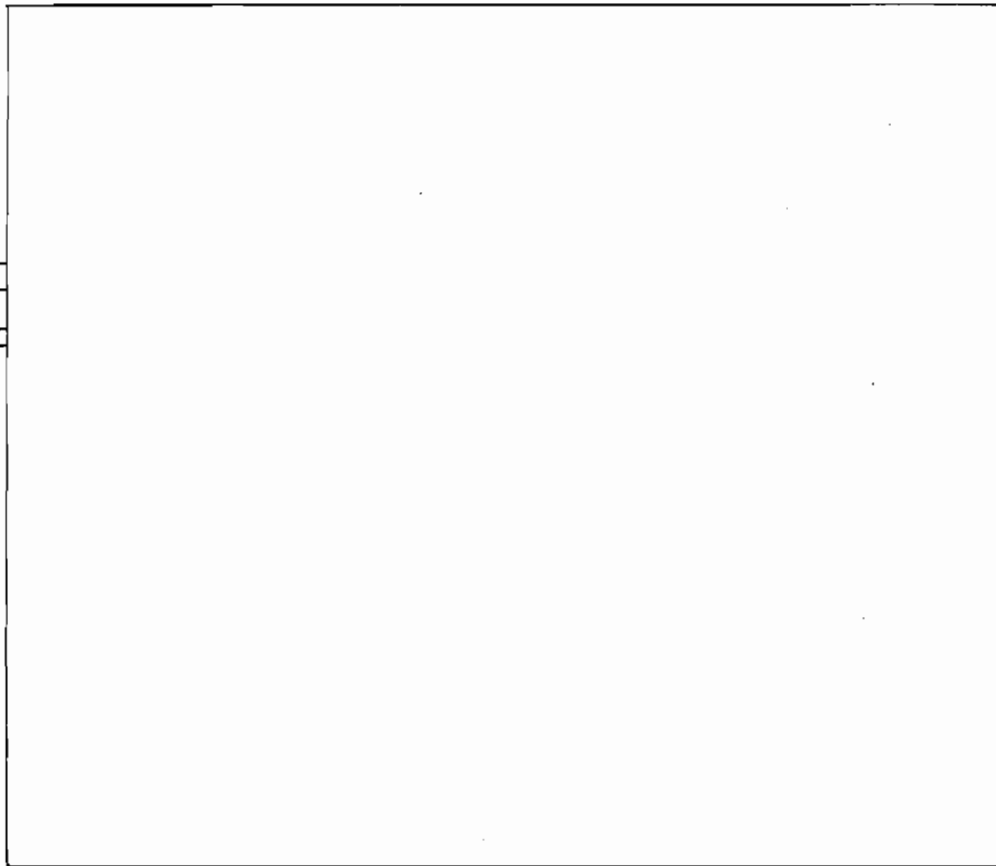
HARRIS SEMICONDUCTOR
AIR PERMIT – BUILDING 59
ATTACHMENT E
MAPS

HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 59









F59S01

F59S03

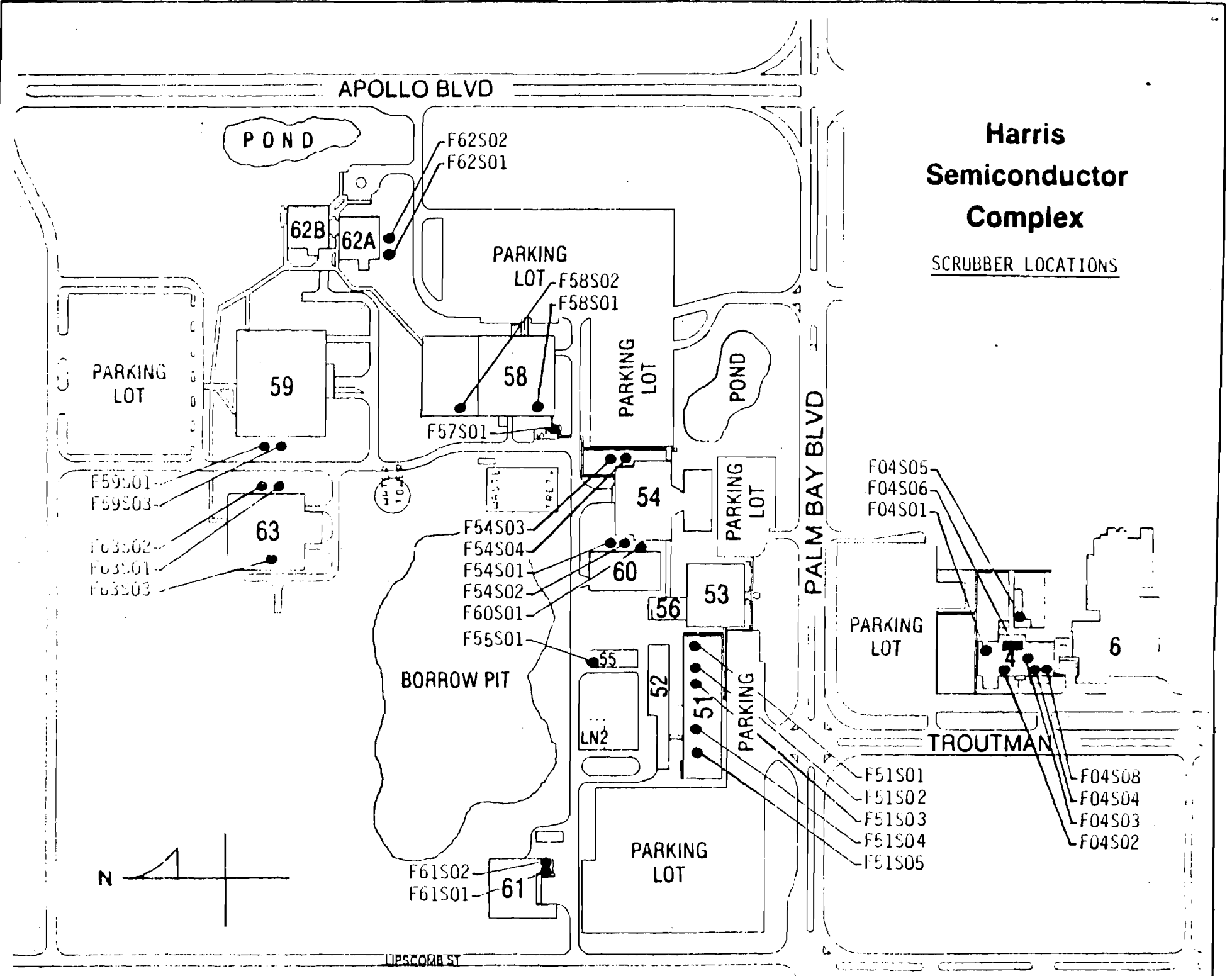


LEGEND

	- Horizontal Scrubber
	- Vertical Scrubber
	- Exhaust Stack
	- Exhaust Fan
	- Stack mounted on fan
	- Epitaxial Scrubber

Harris Semiconductor Complex

SCRUBBER LOCATIONS



PERMITEE:
Harris Semiconductor

Permit Number: AC 05-147321
Expiration Number: April 30, 1990

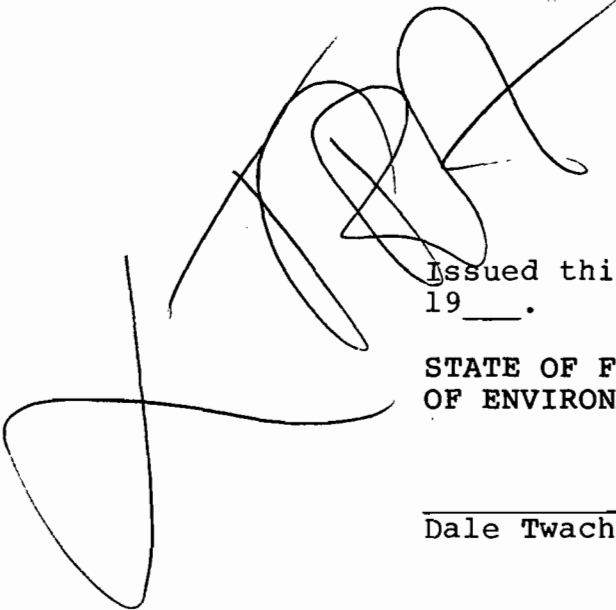
SPECIFIC CONDITIONS:

operate in compliance with all terms of the construction permit until its expiration date in accordance with FAC Rules 17-2 and 17-4.

If the construction permit expires prior to the permittee filing an application for a permit to operate, then all activities at the project must cease pursuant to FAC Rule 17-4.

9. Building 54 is subject to the provisions of FAC Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; 17-4.130: Plant Operation-Problems; and, 17-4.140: Reports.

10. Any modification pursuant to FAC Rule 17-2.100(119) shall be submitted to the DER's Central District office and the Bureau of Air Quality Management office for approval.



Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

Dale Twachtmann, Secretary

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-147321
Expiration Date: April 30, 1990

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's Central Florida District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunctions.

5. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC/solvent emissions limit for Building 54 and shall be determined by a material balance scheme, which includes the following:

- a) a beginning inventory of full containers, cylinders and storage tanks at the beginning of each calendar year;
- b) plus all purchased deliveries after the beginning inventory (verifiable by invoices);
- c) minus all quantities picked-up and shipped-off the premise after the beginning inventory (verifiable by invoices);
- d) minus all quantities deep well injected during the calendar year, justified by assumptions and established scrubber efficiencies; and,
- e) minus an ending inventory of full containers, cylinders, and storage tanks; and, should occur at the beginning of the following calendar year.

6. Each scrubber system's efficiency and potential VOC/solvent emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Reference Method 25A;
- b) the DER's Central Florida District office shall receive 15 days notice in writing prior to sampling; and,
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed.

7. A meter to measure the pressure drop shall be installed on each scrubber system.

8. To obtain a permit to operate, the permittee must demonstrate compliance with the conditions of the construction permit and submit an application for an operating permit, including the application fee, along with the material balance results, compliance test results and Certificate of Completion, to the DER's Central District office 90 days prior to the expiration date of the construction permit. The permittee may continue to

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-147321
Expiration Date: April 30, 1990

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by Department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC/solvent emissions from Building 54 shall be 95.7 tons per year.
2. The VOC/solvent vapor exhaust scrubber must be on during the working hours.
3. Annual operation shall be 8760 hours per year.
4. Objectionable odors shall not be allowed off plant property.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-150794
Expiration Date: April 30, 1990

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by Department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the Department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the Department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC/solvent emissions from Building 59 shall be 0.50 tons per year. The projected potential acid vapor emissions are 0.1 tons per year.
2. The VOC/solvent and acid vapor exhaust scrubbers must be on during the working hours.
3. Annual operation shall be 8760 hours per year.
4. Objectionable odors shall not be allowed off plant property.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-150794
Expiration Date: April 30, 1990

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's Central Florida District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunctions.

5. By March 31 of each calendar year, an annual operating report shall be submitted to the DER's Central District office demonstrating compliance with the VOC/solvent emissions limit for Building 59 and shall be determined by a material balance scheme, which includes the following:

- a) a beginning inventory of full containers, cylinders and storage tanks at the beginning of each calendar year;
- b) plus all purchased deliveries after the beginning inventory (verifiable by invoices);
- c) minus all quantities picked-up and shipped-off the premise after the beginning inventory (verifiable by invoices);
- d) minus all quantities deep well injected during the calendar year, justified by assumptions and established scrubber efficiencies; and,
- e) minus an ending inventory of full containers, cylinders, and storage tanks; and, should occur at the beginning of the following calendar year.

6. Each scrubber system's efficiency and potential VOC/solvent and acid emissions shall be established by a sampling and analysis program, which includes:

- a) a sample shall be taken annually from each scrubber stack and analyzed using EPA Reference Method 25A;
- b) the DER's Central Florida District office shall receive 15 days notice in writing prior to sampling; and,
- c) the report, summarizing the sampling results, shall be submitted to the DER's Central District office within 45 days after the last test run is completed.

7. A meter to measure the pressure drop shall be installed on each scrubber system.

8. To obtain a permit to operate, the permittee must demonstrate compliance with the conditions of the construction permit and submit an application for an operating permit, including the application fee, along with the material balance results, compliance test results and Certificate of Completion, to the DER's Central District office 90 days prior to the expiration date of the construction permit. The permittee may continue to

PERMITEE:
Harris Semiconductor

Permit Number: AC 05-150794
Expiration Number: April 30, 1990

SPECIFIC CONDITIONS:

operate in compliance with all terms of the construction permit until its expiration date in accordance with FAC Rules 17-2 and 17-4.

If the construction permit expires prior to the permittee filing an application for a permit to operate, then all activities at the project must cease pursuant to FAC Rule 17-4.

9. Building 59 is subject to the provisions of FAC Rules 17-2.240: Circumvention; 17-2.250: Excess Emissions; 17-4.130: Plant Operation-Problems; and, 17-4.140: Reports.

10. Any modification pursuant to FAC Rule 17-2.100(119) shall be submitted to the DER's Central District office and the Bureau of Air Quality Management office for approval.

Issued this ____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

Dale Twachtmann, Secretary



FS-JRK-185-88

June 8, 1988

Mr. C. H. Fancy
Deputy Bureau Chief
Department of Environmental Regulation
Bureau of Air Quality Management
2600 Blair Stone Road
Tallahassee, Florida 32301

RECEIVED

JUN 10 1988

DER-BAQM

Reference: HARRIS SEMICONDUCTOR
B-59 Consolidated Air Permit

Dear Mr. Fancy:

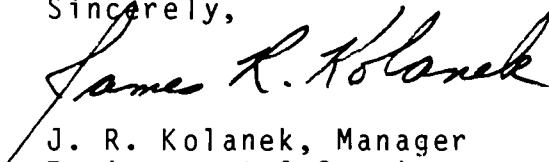
On February 17, 1988, representatives from Harris and the Florida DER met in Orlando to discuss the status of air permits at Harris Semiconductor's facility in Palm Bay. At that meeting it was agreed that Harris would submit modified air permits. The purpose of the permit modifications was as follows:

1. Consolidate permits on a by building basis to reduce the existing number of permits.
2. To accurately quantify the current air emissions.

Enclosed is the modified permit application for Semiconductor's Building 59.

If you should have any questions about the enclosed information, please feel free to contact me at (407) 724-7467.

Sincerely,


J. R. Kolanek, Manager
Environmental Services

/pgc

cc: A. T. Sawicki
L. R. Hutker
D. R. Erdley
R. R. Sands

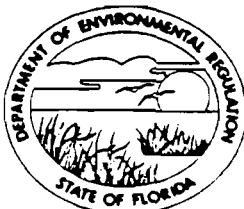
DEPARTMENT OF ENVIRONMENTAL REGULATION

AC 05-150794

RECEIVED BOB GRAHAM GOVERNOR

JUN 10 1988 VICTORIA J. TSCHINKEL SECRETARY

WIN TOWERS OFFICE BUILDING
2800 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



APPLICATION TO OPERATE/CONSTRUCT AIR POLLUTION ~~SOURCES~~ ^{DER BAQM}

SOURCE TYPE: Stationary [] New¹ [] Existing¹

APPLICATION TYPE: [] Construction [] Operation [] Modification

COMPANY NAME: Harris Semiconductor COUNTY: Brevard

Identify the specific emission point source(s) addressed in this application (i.e. Lime Kiln No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired) B-59 Manufacturing Fab

SOURCE LOCATION: Street Palm Bay Road City Palm Bay

UTM: East 17-538700 North 17-3100900

Latitude 28° 01' 20"N Longitude 80° 36' 10"W

APPLICANT NAME AND TITLE: J. R. Kolanek, Manager Environmental Services

APPLICANT ADDRESS: P.O. Box 883, Melbourne, Florida 32901

SECTION I: STATEMENTS BY APPLICANT AND ENGINEER

A. APPLICANT

I am the undersigned owner or authorized representative* of Harris Semiconductor

I certify that the statements made in this application for a modified permit are true, correct and complete to the best of my knowledge and belief. Further, I agree to maintain and operate the pollution control source and pollution control facilities in such a manner as to comply with the provision of Chapter 403, Florida Statutes, and all the rules and regulations of the department and revisions thereof. I also understand that a permit, if granted by the department, will be non-transferable and I will promptly notify the department upon sale or legal transfer of the permitted establishment.

*Attach letter of authorization

Signed: James R. Kolanek

J. R. Kolanek, Manager, Environmental Services
Name and Title (Please Type)

Date: 5/18/88 Telephone No. (407) 724-7467

B. PROFESSIONAL ENGINEER REGISTERED IN FLORIDA (where required by Chapter 471, F.S.)

This is to certify that the engineering features of this pollution control project have been designed/examined by me and found to be in conformity with modern engineering principles applicable to the treatment and disposal of pollutants characterized in the permit application. There is reasonable assurance, in my professional judgment, that

¹ See Florida Administrative Code Rule 17-2.100(57) and (104)

the pollution control facilities, when properly maintained and operated, will discharge an effluent that complies with all applicable statutes of the State of Florida and the rules and regulations of the department. It is also agreed that the undersigned will furnish, if authorized by the owner, the applicant a set of instructions for the proper maintenance and operation of the pollution control facilities and, if applicable, pollution sources.

Signed Lawrence R. Hutker

Lawrence R. Hutker
Name (Please Type)

Harris Semiconductor
Company Name (Please Type)

P.O. Box 883, Melbourne, Florida 32901
Mailing Address (Please Type)

Florida Registration No. 35972 Date: 5/18/88 Telephone No. (407) 729-4655

SECTION II: GENERAL PROJECT INFORMATION

1. Describe the nature and extent of the project. Refer to pollution control equipment, and expected improvements in source performance as a result of installation. State whether the project will result in full compliance. Attach additional sheet if necessary.

This is a modification and consolidation of existing air permits.

2. Schedule of project covered in this application (Construction Permit Application Only)

Start of Construction N/A Completion of Construction N/A

3. Costs of pollution control system(s): (Note: Show breakdown of estimated costs only for individual components/units of the project serving pollution control purposes. Information on actual costs shall be furnished with the application for operation permit.)

N/A

4. Indicate any previous DER permits, orders and notices associated with the emission point, including permit issuance and expiration dates.

AO 05-121924 issued 9/17/86; expires 9/14/91

AC 05-104515 issued 1/15/86; expires 6/30/86

E. Requested permitted equipment operating time: hrs/day 24 ; days/wk 7 ; wks/yr 52 ;
if power plant, hrs/yr _____ ; if seasonal, describe: _____

F. If this is a new source or major modification, answer the following questions.
(Yes or No)

1. Is this source in a non-attainment area for a particular pollutant? No
a. If yes, has "offset" been applied? _____
b. If yes, has "Lowest Achievable Emission Rate" been applied? _____
c. If yes, list non-attainment pollutants. _____

2. Does best available control technology (SACT) apply to this source?
If yes, see Section VI. No

3. Does the State "Prevention of Significant Deterioration" (PSD)
requirement apply to this source? If yes, see Sections VI and VII. No

4. Do "Standards of Performance for New Stationary Sources" (NSPS)
apply to this source? No

5. Do "National Emission Standards for Hazardous Air Pollutants"
(NESHAP) apply to this source? No

H. Do "Reasonably Available Control Technology" (RACT) requirements apply
to this source? No

a. If yes, for what pollutants? _____

b. If yes, in addition to the information required in this form,
any information requested in Rule 17-2.650 must be submitted.

Attach all supportive information related to any answer of "Yes". Attach any justifi-
cation for any answer of "No" that might be considered questionable.

SECTION III: AIR POLLUTION SOURCES & CONTROL DEVICES (Other than Incinerators)

A. Raw Materials and Chemicals Used in your Process, if applicable:

Description	Contaminants		Utilization Rate - lbs/hr	Relate to Flow Diagram
	Type	% Wt		
---SEE ATTACHMENT C ---				

B. Process Rate, if applicable: (See Section V, Item 1)

1. Total Process Input Rate (lbs/hr): not applicable

2. Product Weight (lbs/hr): not applicable

C. Airborne Contaminants Emitted: (Information in this table must be submitted for each emission point, use additional sheets as necessary)

Name of Contaminant	Emission ¹		Allowed Emission Rate per Rule 17-2	Allowable ³ Emission lbs/hr	Potential ⁴ Emission		Relate to Flow Diagram
	Maximum lbs/hr	Actual T/yr			lbs/yr	T/yr	
---SEE ATTACHMENT B ---							

¹See Section V, Item 2.

²Reference applicable emission standards and units (e.g. Rule 17-2.600(5)(b)2. Table II, E. (1) - 0.1 pounds per million BTU heat input)

³Calculated from operating rate and applicable standard.

⁴Emission, if source operated without control (See Section V, Item 3).

J. Control Devices: (See Section V, Item 4)

Name and Type (Model & Serial No.)	Contaminant	Efficiency	Range of Particles Size Collected (in microns) (If applicable)	Basis for Efficiency (Section V Item 5)
---SEE ATTACHMENT D ---				

E. Fuels

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	avg/hr	max./hr	

*Units: Natural Gas--MMCF/hr; Fuel Oils--gallons/hr; Coal, wood, refuse, other--lbs/hr.

Fuel Analysis:

Percent Sulfur: _____ Percent Ash: _____

Density: _____ lbs/gal Typical Percent Nitrogen: _____

Heat Capacity: _____ BTU/lb _____ BTU/gal

Other Fuel Contaminants (which may cause air pollution): _____

F. If applicable, indicate the percent of fuel used for space heating.

Annual Average _____ Maximum _____

G. Indicate liquid or solid wastes generated and method of disposal.

Waste water from air scrubbers is discharged to on-site Waste Water Treatment

Plant--discharge to deepwell under UIC - Permit #UC05-126519.

-----SEE ATTACHMENT D-----

H. Emission Stack Geometry and Flow Characteristics (Provide data for each stack):

Stack Height: _____ ft. Stack Diameter: _____ ft.
 Gas Flow Rate: _____ ACFM _____ DSCFM Gas Exit Temperature: _____ °F.
 Water Vapor Content: _____ % Velocity: _____ FPS

SECTION IV: INCINERATOR INFORMATION

not applicable

Type of Waste	Type 0 (Plastics)	Type I (Rubbish)	Type II (Refuse)	Type III (Garbage)	Type IV (Pathological)	Type V (Liq. & Gas By-prod.)	Type VI (Solid By-prod.)
Actual lb/hr Incinerated							
Uncontrolled (lbs/hr)							

Description of Waste _____

Total Weight Incinerated (lbs/hr) _____ Design Capacity (lbs/hr) _____

Approximate Number of Hours of Operation per day _____ day/wk _____ wks/yr. _____

Manufacturer _____

Date Constructed _____ Model No. _____

	Volume (ft) ³	Heat Release (BTU/hr)	Fuel		Temperature (°F)
			Type	BTU/hr	
Primary Chamber					
Secondary Chamber					

Stack Height: _____ ft. Stack Diameter: _____ Stack Temp. _____

Gas Flow Rate: _____ ACFM _____ DSCFM* Velocity: _____ FPS

*If 50 or more tons per day design capacity, submit the emissions rate in grains per standard cubic foot dry gas corrected to 50% excess air.

Type of pollution control device: Cyclone Wet Scrubber Afterburner
 Other (specify) _____

Brief description of operating characteristics of control devices: _____

Ultimate disposal of any effluent other than that emitted from the stack (scrubber water, ash, etc.):

NOTE: Items 2, 3, 4, 6, 7, 8, and 10 in Section V must be included where applicable.

SECTION V: SUPPLEMENTAL REQUIREMENTS

Please provide the following supplements where required for this application.

1. Total process input rate and product weight -- show derivation [Rule 17-2.100(127)]
2. To a construction application, attach basis of emission estimate (e.g., design calculations, design drawings, pertinent manufacturer's test data, etc.) and attach proposed methods (e.g., FR Part 60 Methods 1, 2, 3, 4, 5) to show proof of compliance with applicable standards. To an operation application, attach test results or methods used to show proof of compliance. Information provided when applying for an operation permit from a construction permit shall be indicative of the time at which the test was made.
3. Attach basis of potential discharge (e.g., emission factor, that is, AP42 test).
4. With construction permit application, include design details for all air pollution control systems (e.g., for baghouse include cloth to air ratio; for scrubber include cross-section sketch, design pressure drop, etc.)
5. With construction permit application, attach derivation of control device(s) efficiency. Include test or design data. Items 2, 3 and 5 should be consistent: actual emissions = potential (1-efficiency).
6. An 8 1/2" x 11" flow diagram which will, without revealing trade secrets, identify the individual operations and/or processes. Indicate where raw materials enter, where solid and liquid waste exit, where gaseous emissions and/or airborne particles are evolved and where finished products are obtained.
7. An 8 1/2" x 11" plot plan showing the location of the establishment, and points of airborne emissions, in relation to the surrounding area, residences and other permanent structures and roadways (Example: Copy of relevant portion of USGS topographic map).
8. An 8 1/2" x 11" plot plan of facility showing the location of manufacturing processes and outlets for airborne emissions. Relate all flows to the flow diagram.

9. The appropriate application fee in accordance with Rule 17-4.05. The check should be made payable to the Department of Environmental Regulation.
10. With an application for operation permit, attach a Certificate of Completion of Construction indicating that the source was constructed as shown in the construction permit.

SECTION VI: BEST AVAILABLE CONTROL TECHNOLOGY

- A. Are standards of performance for new stationary sources pursuant to 40 C.F.R. Part 60 applicable to the source?

Yes No

Contaminant	Rate or Concentration

- B. Has EPA declared the best available control technology for this class of sources (if yes, attach copy)

Yes No

Contaminant	Rate or Concentration

- C. What emission levels do you propose as best available control technology?

Contaminant	Rate or Concentration

- D. Describe the existing control and treatment technology (if any).

- | | |
|---------------------------|--------------------------|
| 1. Control Device/System: | 2. Operating Principles: |
| 3. Efficiency:* | 4. Capital Costs: |

*Explain method of determining

5. Useful Life:

6. Operating Costs:

7. Energy:

8. Maintenance Cost:

9. Emissions:

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

10. Stack Parameters

a. Height: ft. b. Diameter: ft.

c. Flow Rate: ACFM d. Temperature: °F.

e. Velocity: FPS

E. Describe the control and treatment technology available (As many types as applicable, use additional pages if necessary).

1.

a. Control Device: b. Operating Principles:

c. Efficiency:¹ d. Capital Cost:

e. Useful Life: f. Operating Cost:

g. Energy:² h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

2.

a. Control Device: b. Operating Principles:

c. Efficiency:¹ d. Capital Cost:

e. Useful Life: f. Operating Cost:

g. Energy:² h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

¹Explain method of determining efficiency.

²Energy to be reported in units of electrical power - KWH design rate.

- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

3.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Cost:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

4.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Costs:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

F. Describe the control technology selected:

- 1. Control Device:
- 2. Efficiency:¹
- 3. Capital Cost:
- 4. Useful Life:
- 5. Operating Cost:
- 6. Energy:²
- 7. Maintenance Cost:
- 8. Manufacturer:
- 9. Other locations where employed on similar processes:
- a. (1) Company:
- (2) Mailing Address:
- (3) City:
- (4) State:

Explain method of determining efficiency.

Energy to be reported in units of electrical power - KWH design rate.

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant

Rate or Concentration

(8) Process Rate:¹

b. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant

Rate or Concentration

(8) Process Rate:¹

10. Reason for selection and description of systems:

¹Applicant must provide this information when available. Should this information not be available, applicant must state the reason(s) why.

SECTION VII - PREVENTION OF SIGNIFICANT DETERIORATION

A. Company Monitored Data

1. _____ no. sites _____ TSP _____ () SO₂+ _____ Wind spd/dir

Period of Monitoring _____ / _____ / _____ to _____ / _____ / _____
month day year month day year

Other data recorded _____

Attach all data or statistical summaries to this application.

Specify bubbler (B) or continuous (C).

2. Instrumentation, Field and Laboratory

a. Was instrumentation EPA referenced or its equivalent? Yes No

b. Was instrumentation calibrated in accordance with Department procedures?

Yes No Unknown

B. Meteorological Data Used for Air Quality Modeling

1. _____ Year(s) of data from _____ / _____ / _____ to _____ / _____ / _____
month day year month day year

2. Surface data obtained from (location) _____

3. Upper air (mixing height) data obtained from (location) _____

4. Stability wind rose (STAR) data obtained from (location) _____

C. Computer Models Used

1. _____ Modified? If yes, attach description.

2. _____ Modified? If yes, attach description.

3. _____ Modified? If yes, attach description.

4. _____ Modified? If yes, attach description.

Attach copies of all final model runs showing input data, receptor locations, and principle output tables.

D. Applicants Maximum Allowable Emission Data

Pollutant	Emission Rate
TSP	_____ grams/sec
SO ₂	_____ grams/sec

E. Emission Data Used in Modeling

Attach list of emission sources. Emission data required is source name, description of point source (on NEDS point number), UTM coordinates, stack data, allowable emissions, and normal operating time.

F. Attach all other information supportive to the PSD review.

G. Discuss the social and economic impact of the selected technology versus other applicable technologies (i.e., jobs, payroll, production, taxes, energy, etc.). Include assessment of the environmental impact of the sources.

H. Attach scientific, engineering, and technical material, reports, publications, journals, and other competent relevant information describing the theory and application of the requested best available control technology.

HARRIS SEMICONDUCTOR
AIR PERMIT - BUILDING 59
ATTACHMENT A
PROCESS DESCRIPTION

Attachment A

Building 59 houses a wafer fabrication facility on the second floor. The fabrication area employs a series of manufacturing procedures referred to as layering, patterning, doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

In the controlled environment of the fabrication clean room, wafer surfaces first undergo acid and/or solvent cleaning, followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process, the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "alligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques.

In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Fumes from the vapor deposition furnaces are oxidized in 'burn boxes.' The oxidized gases are then exhausted to scrubber systems. Additional material may be layered on the wafer surface in vapor and crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation.

Thirteen exhausted wet stations that house vats containing a variety of acid and caustic compounds are in the fabrication facility. Five of these stations contain solvents, one of which is heated.

The ground floor of the two-story manufacturing area houses a process equipment support room that contains gas cabinets, chemical storage cabinets, vacuum pumps and drains. These exhausted units service the process equipment which resides above it in the fabrication area. Storage cabinets safely hold virgin chemicals until they are ready for use. Gas cabinets house cylinders that supply process gases to the 'fab' operations. In addition, several waste collection areas are exhausted. The ground floor also houses the site's distilled water plant, and a mechanical equipment storage area.

The exhaust system for the building is divided between two scrubbers. Acid vapors are vented to scrubber number F59S01, while solvent exhaust streams are ducted to scrubber number F59S03. Both systems reside on the site grounds directly outside the west wall of the building. (See site plan and scrubber location maps attached.)

HARRIS SEMICONDUCTOR
AIR PERMIT - BUILDING 59

ATTACHMENT B
AIR EMISSIONS

Attachment B

Monitoring work was performed on the building 59 solvent scrubber system in December of 1986. The test conducted to establish VOC emissions from the fab was EPA method 25A (flame ionization detector.)

The test results initially revealed that total accumulative monitored VOC emissions for the building were 0.37 tons/year expressed as propane. Building 59 houses the site's newest and most technologically sophisticated clean room. Due to increased customer interest in the products manufactured in this building, production schedules are likely to vary. In order to accomodate these fluctuations, total VOC emissions were adjusted to represent maximum loading. Hence, an 8760 hour a year production schedule was utilized to calculate emissions, and the loading was estimated to be 0.50 tons/year. Fluctuations in production schedules are common at Semiconductor, because manufacturing hours depend on product demand. The following assumptions was made regarding monitoring work on this building:

-VOC values refer to all organic emissions including organic solvents, as defined in the Florida Environmental Regulations.

Total projected VOC emissions for building 59 is 0.57 tons/year. This number is representative of maximum VOC emissions, and is an extrapolation of the building's monitored emission rate mentioned above. The site's projected VOC limit is 150 tons/year.

No monitoring work to estimate acid emissions has been performed to date. Scrubber removal efficiencies as prescribed by the scrubber manufacturer (Beverly Pacific Corporation) are provided in this attachment. Semiconductor's Environmental Services Department plans to verify these acid removal efficiencies sometime within the calendar year.

EPA METHOD 25-A (F.I.D. ANALYSIS) BUILDING 59
 VOC EMISSIONS DURING PRODUCTION HOURS

TEST DATE	SCRUBBER #	VOC EMISSIONS (TON/YR)
12/09/86	F59S03	0.50

NOTE: ABOVE BASED ON ACTUAL OPERATING HOURS.

TOTAL VOC EMISSIONS FROM BUILDING 59
 AS DETECTED BY EPA METHOD 25-A

SCRUB#	PRODUCTN SCHEDULE	NONPRODUCTN SCHEDULE	PRODUCTN EMISSIONS (TON/YR)	NONPRODUCTN EMISSIONS (TON/YR)	TOTAL VOC EMISSIONS (TON/YR)
F59S03	8760	0	0.50	0	0.50

TOTAL PROJECTED VOC EMISSIONS FOR BLDG 59 = 0.57 TONS/YEAR

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BEVERLY PACIFIC CORP.

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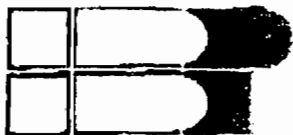
TABLE OF SCRUBBER EFFICIENCIES/CONTAMINANTS

Information given below is to be used as a guide only

<u>CONTAMINANTS</u>	<u>TYPE (SEE NOTE A)</u>	<u>BPE APPROX. EFFICIENCY</u>
Acetic Acid (CH ₃ CO ₂ H)	G & L	95.7%
Acetone (CH ₃ COCH ₃)	G	95%
Aluminum Bright Dip	G & L	40-65%
(2) Amines (RNH ₂)	G	98-99%
(2) Ammonia (NH ₂)	G	97-99%
Ammonia Hydroxide (NH ₄ OH)	L	97-99%
Ammonia Nitrate (NH ₄ NO ₃)	S & SS	98-99%
Anodizing Solutions	L	99%
Ascorbic Acid (H ₃ BO ₃)	L	95-98%
(1) Bromine (BR ₂)	G	99%
(1) Carbon Dioxide (CO ₂)	G	80-90%
Caustic (NaOH)	L	99%
(1) Chlorine (Cl ₂)	G	99%
(3) Chlorine Dioxide (ClO ₂)	G	95-98%
Chromic Acid (H ₂ CrO ₄)	L	99%
Citric Acid	L	98-99%
Cyanide Salts	L	99%
Ethanol (CH ₃ CH ₂ OH)	G & L	99%
(1) Formaldehyde (HCHO)	G & L	98-99%
Formic Acid (HCO ₂ H)	G	98-99%
Hydrobromic Acid (HBr)	G & L	98-99%
Hydrochloric Acid (HCl)	G, L & SL	95-99%

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Hydrofluoric Acid (HF)	G	95-97%
Hydrogen Cyanide (HCN)	G	99%
Hydrogen Peroxide	G	95%
Hydrogen Sulfide (H ₂ S)	G	99%
(3) Mercaptans (RSH)	G & L	98-99%
Methanol (CH ₃ OH)	G	97.5%
Nitric Acid (HNO ₃)	L	95%
(1) Nitrogen Oxides (NO _x)	G	30-40%
Oil Mists	L & SL	95-98%
Perchloric Acid	G	98-99%
Phenol (C ₆ H ₅ OH)	G & L	95-99%
Phosphate Salt Baths	L	98-99%+
Phosphoric Acid (H ₃ PO ₄)	L	98-99%+
Silicon Tetrachloride (SiCl ₄)	G	99%
Silicon Tetrafluoride (SiF ₄)	G	99%
Sodium Chloride (NaCl)	S & L	98-99%+
Sulfuric Acid (H ₂ SO ₄)	L	95%
(1) Sulfur Dioxide (SO ₂)	G	87-90%
Urea (H ₂ NCONH ₂)	S & SS	98-99%
(1) Hydrogen Sulfide (H ₂ S)	G	98-99%
Xylene	L	95%



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Note A: G = Gas
L = Liquid particulate
above 3 microns
SL = Liquid particulate
below 3 microns
S = Solid particulate
above 3 microns
SS = Solid particulate
below 3 microns

Notes:
(1) NaOH Scrubbing liquid
required
(2) H2SO4 scrubbing liquid
may be required
(3) Special scrubbing liquid
required
Consult BPC for
recommendation
4. Consult BPC if
efficiencies other than
shown are required or
for contams. not shown

HARRIS SEMICONDUCTOR

AIR PERMIT - BUILDING 59

ATTACHMENT C

RAW MATERIALS AND CHEMICALS

HARRIS SEMICONDUCTOR
BUILDING 59 CONSOLIDATED AIR PERMIT
PROCESS GASSES

- 1 ARGON
- 2 BORON TRIBROMIDE
- 3 BORON TRIFLUORIDE
- 4 CHLORINE
- 5 DICHLOROSILANE
- 6 HELIUM
- 7 HYDROGEN
- 8 HYDROGEN CHLORIDE
- 9 NITROGEN
- 10 NITROGEN TRIFLUORIDE
- 11 NITROUS OXIDE
- 12 OXYGEN
- 13 OZONE
- 14 PHOSPHINE
- 15 PHOSPHOROUS OXYCHLORIDE
- 16 SILANE
- 17 SULFUR HEXAFLUORIDE
- 18 TRIMETHYL BORATE
- 19 TRIMETHYL PHOSPHATE
- 20 TUNGSTON HEXAFLUORIDE
- 21 HEXAFLUOROETHANE

JUNE 8, 1988

HARRIS SEMICONDUCTOR
BUILDING 59 CONSOLIDATED AIR PERMIT
PROCESS SOLVENTS

- 1 ACETONE
- 2 CARBON TETRACHLORIDE
- 3 1,1,1 TRICHLOROETHANE
- 4 FREON TF
- 5 FREON TMS
- 6 N-BUTYL ALCOHOL
- 7 METHANOL
- 8 BUTYL CELLOSOLVE
- 9 2-ETHOXYETHYL ACETATE
- 10 CELLOSOLVE ACETATE
- 11 DICHLORODIFLUOROETHANE
- 12 EDTA
- 13 ETHYL ALCOHOL
- 14 ETHYL BENZENE
- 15 ISOPROPYL ALCOHOL
- 16 METHYLPHENYL ETHER
- 17 MONOETHANOLAMINE
- 18 N-BUTYL ACETATE
- 19 TOLUENE
- 20 XYLENE
- 21 TRICHLOROTRIFLUOROETHANE
- 22 N-METHYL PYRROLIDONE
- 23 METHYL-2-PYRROLIDINONE
- 24 PROPYLENE GLYCOL 1,2 PROPANEDIOL

JUNE 8, 1988

HARRIS SEMICONDUCTOR
BUILDING 59 CONSOLIDATED AIR PERMIT
PROCESS CHEMICALS

- 1 AMMONIA
- 2 AMMONIUM FLUORIDE
- 3 AMMONIUM HYDROXIDE
- 4 ETHYLENE GLYCOL
- 5 GLYCERINE
- 6 HYDROCHLORIC ACID
- 7 HYDROFLUORIC ACID
- 8 HYDROGEN PEROXIDE
- 9 MOLYBDENUM DISULFIDE
- 10 NITRIC ACID
- 11 OIL
- 12 PHOSPHORIC ACID
- 13 POTASSIUM DICHROMATE
- 14 POTASSIUM PHOSPHATE
- 15 RED PHOSPHOROUS
- 16 SODIUM CARBONATE
- 17 SODIUM HYDROXIDE
- 18 SODIUM PHOSPHATE
- 19 SULFURIC ACID
- 20 TETRAMETHYL AMMONIUM HYDROXIDE
- 21 TRISODIUM PHOSPHITE

JUNE 8, 1988

HARRIS SEMICONDUCTOR
AIR PERMIT - BUILDING 59

ATTACHMENT D
CONTROL EQUIPMENT

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 59 DATE ISSUED : 09/17/86
PERMIT NUMBER: AD 05-121924 RENEWAL DATE: 07/16/91
PERMIT TYPE : OPERATING DATE EXPIRES: 09/14/91

AREA SERVED:
PROCESS DESCRIPTION: ACID VAPOR SCRUBBER

PERMIT LIMITS

VOL. RATE (SCFM): 40,000
ACID MIST (LB/HR): 0.0079
SOLVENTS (LB/HR): --
VOCs (LB/HR): --
OPER. (HRS/YEAR): 2112

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT : 03/01
NOTIFICATION OF VE TEST : 10/26
ANNUAL VIS EMISSION TEST: 11/10

EQUIPMENT INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-40HT
LOCATION : B59 GROUND WEST SIDE
HARRIS ID NUMBER : F59501 STACK HEIGHT (FT): 35
VOLUME FLOW RATE (CFM): 40,000 STACK DIAMETER (IN): 44
RECIRCULATION RATE (GPM): 175 STACK VELOCITY (FPM):
MAKEUP WATER RATE (GPM): 17.5 DUCT MATERIAL : polypro

PERMIT HISTORY

PERMIT NUMBER: AC 05-54991
DATE EXPIRED : 06/01/84

PERMIT NUMBER: AC 05-104516
DATE EXPIRED : 06/30/86

PERMIT NUMBER:
DATE EXPIRED :

SCRUBBER INFORMATION

HARRIS ID # : F59S01
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-40HT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : HORIZONTAL CROSS FLOW, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR, DWG. F-600-1

DESIGN DATA

VOLUME FLOW RATE (CFM): 40,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 175 MAKE UP RATE (GPM): 17.5

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE:
RECIRCULATION RATE (GPM): 90 MAKE UP RATE (GPM): 2.5 DATE: 01/16/87

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP INC MODEL NUMBER : 36E188-105
SERIAL NUMBER: F1280 HP : 3 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5912

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-49
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD CURVED BLADES,
DWG. F-600-1

DESIGN DATA

VOLUME FLOW RATE (CFM): 33,384 STATIC PRESS (IN): 5.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): 764 DATE: SUBMITTAL

STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : RPM :
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5913

HARRIS SEMICONDUCTOR -- AIR PERMIT INFORMATION

CURRENT PERMIT

BUILDING: 59 DATE ISSUED : 01/15/86
PERMIT NUMBER: AC 05-104515 RENEWAL DATE: 04/01/86
PERMIT TYPE : CONSTRUCTION DATE EXPIRES: 06/30/86

AREA SERVED:

PROCESS DESCRIPTION: VOC/SOLVENT SCRUBBER .

PERMIT LIMITS

VOL. RATE (SCFM): 20,000
ACID MIST (LB/HR): --
SOLVENTS (LB/HR): 0.0018
VOCS (LB/HR): --
OPER. (HRS/YEAR): 2112

SPECIFIC CONDITIONS

ANNUAL OPERATING REPORT :
NOTIFICATION OF VE TEST :
ANNUAL VIS EMISSION TEST:

EQUIPMENT INFORMATION

MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-24UT
LOCATION : B59 GROUND WEST SIDE
HARRIS ID NUMBER : F59S03 STACK HEIGHT (FT): 35
VOLUME FLOW RATE (CFM): 24,000 STACK DIAMETER (IN): 42
RECIRCULATION RATE (GPM): 105 STACK VELOCITY (FPM):
MAKEUP WATER RATE (GPM): 10.5 DUCT MATERIAL : galv.

PERMIT HISTORY

PERMIT NUMBER: AC 05-54990
DATE EXPIRED : 06/01/84

PERMIT NUMBER: AC 05-104515
DATE EXPIRED : 06/30/86

PERMIT NUMBER:
DATE EXPIRED :

SCRUBBER INFORMATION

HARRIS ID # : F59503
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER : PS-24VT
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : VERTICAL COUNTER-CURRENT, NON-CLOGGING PVC SPRAY NOZZLES,
POLYPROPYLENE PACKING, PVC MIST ELIMINATOR, DWG. F-600-2

DESIGN DATA

VOLUME FLOW RATE (CFM): 24,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 105 MAKE UP RATE (GPM): 10.5

ACTUAL DATA

VOLUME FLOW RATE (CFM): 5,494 PRESSURE DROP (IN): N/E DATE: 12/09/86
RECIRCULATION RATE (GPM): 30 MAKE UP RATE (GPM): 2.5 DATE: 01/16/87

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FILTER PUMP IND MODEL NUMBER : 36E188-105
SERIAL NUMBER: F1280 HP : 3 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5912

FAN INFORMATION

HARRIS ID # :
MANUFACTURER : BEVERLY PACIFIC MODEL NUMBER: CB-36
SERIAL NUMBER: F-600 MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL TYPE, CLASS II, BACKWARD CURVED BLADES,
DWG. F-600-2

DESIGN DATA

VOLUME FLOW RATE (CFM): 16,000 STATIC PRESS (IN): 6.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): 5,494 SPEED (RPM): 1094 DATE: SUBMITTAL
STATIC PRESS (IN): DATE: 12/09/86

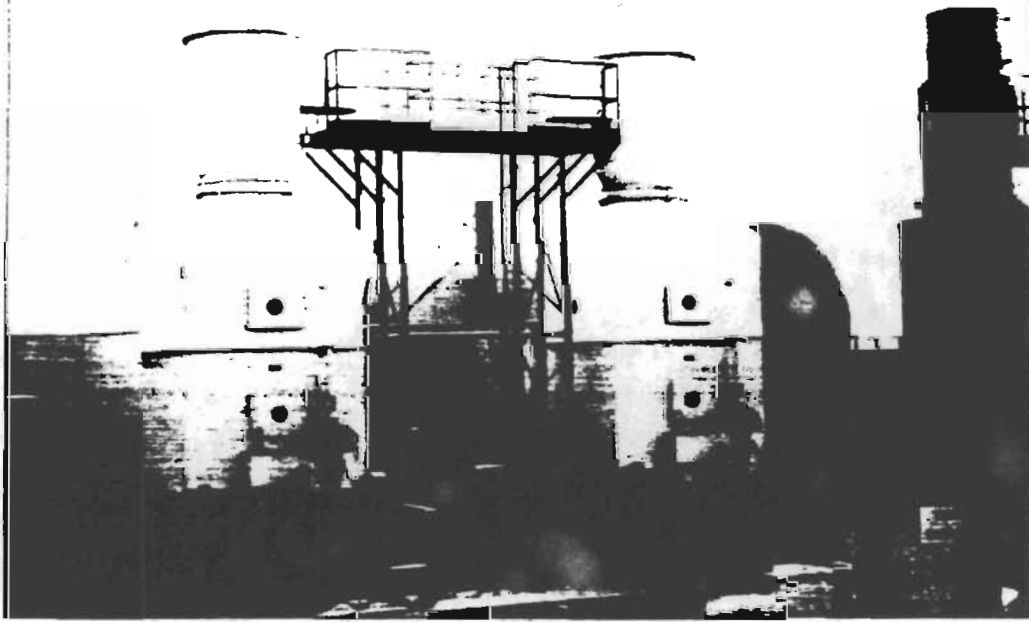
FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : RPM :
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : 5913



BEVERLY PACIFIC CORPORATION

SCRUBBERS



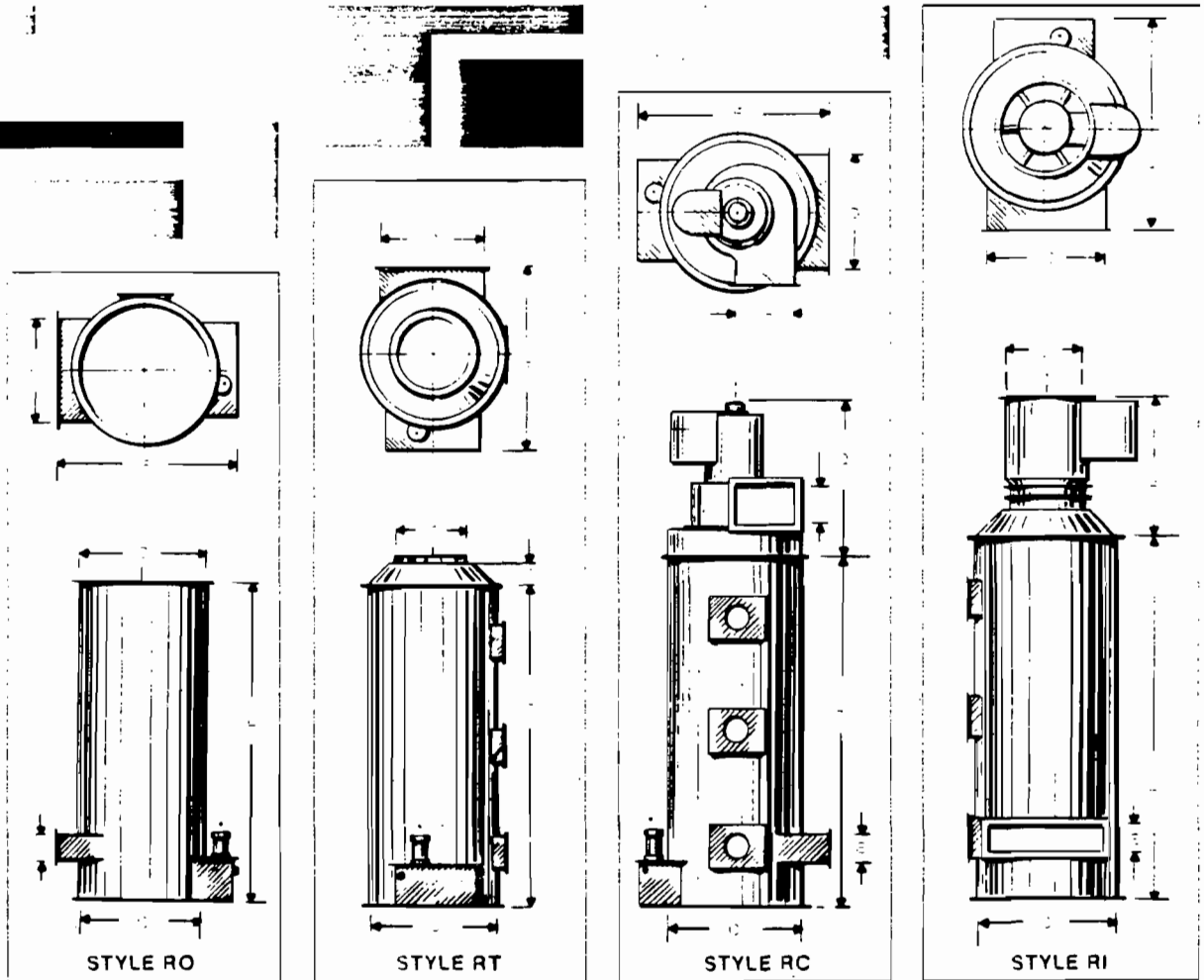
FIBERGLASS REINFORCED PLASTIC

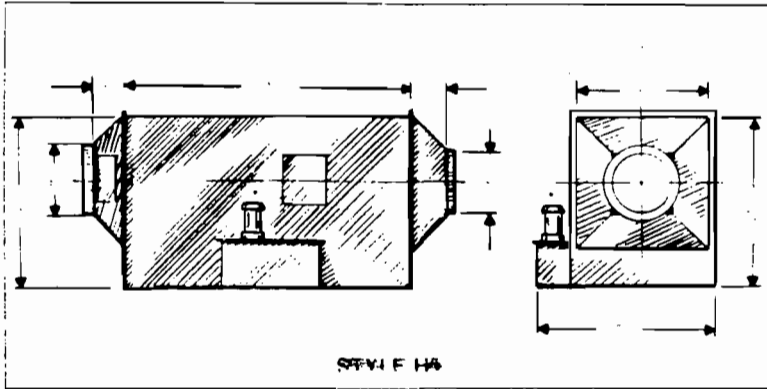
PACKED SCRUBBER DIMENSIONAL CHART

MODEL NUMBERS

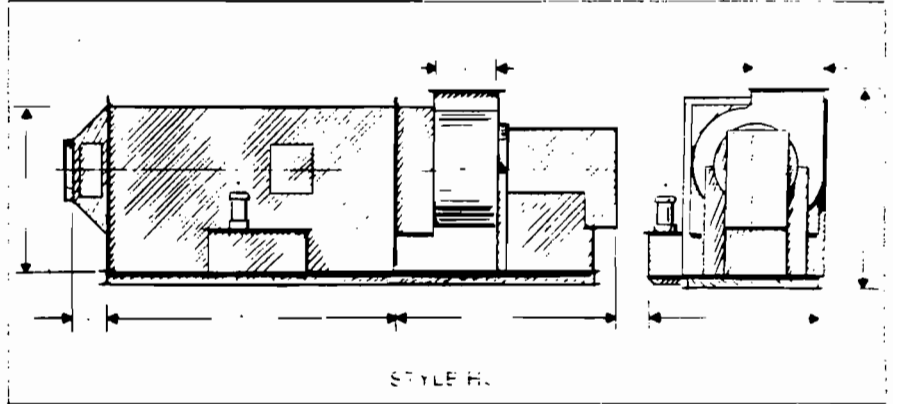
DIMENSIONS IN INCHES

	PS-2	PS-4	PS-6	PS-8	PS-12	PS-18	PS-24	PS-30	PS-40	PS-50
A	78	82	84	94	101	108	112	114	118	118
B	24	36	42	48	60	72	84	96	106	120
C	28	40	48	58	72	84	96	108	120	136
D	22	34	40	46	58	70	80	92	104	116
E	6	8	10	11	12	16	18	20	24	24
F	46	58	66	76	90	102	114	126	138	154
G	42	54	60	66	78	90	102	114	126	138
H	13½	16½	22½	26¼	29½	35¼	39	47¼	52½	63½
I	10½	12½	17	20½	22¼	27	30	37½	40½	49½
J	18	22	28	34	38	45	50	62	66	80
K	6	8	10	10	12	16	19	20	24	24
L	84	87	89	104	112	118	122	124	128	128
M	64	64	70	77	89	102	102	102	114	114
N	35	49	55	62	76	88	103	116	128	142
O	38	52	58	65	79	91	106	119	131	145
P	14	16	22	26	30	36	42	50	54	66
Q	45	50	61	64	68	72	78	86	93	103
R	35	44	55	65	75	85	94	108	120	141
S	46	52	59	69	72	79	82	97	100	110
T	36	48	54	60	72	84	96	108	120	132
WHEEL DIA.	12¼	15	20	24½	27	33	36½	44½	49	60
CFM x 1000	1-2	2-4	4-6	6-8	8-12	12-18	18-24	24-30	40	40-50
RECIRC. GPM	7	15	25	35	45	75	105	135	75	225
MAKE-UP GPM	0.7	1.5	2.0	3.0	4.0	7.0	10.0	13.0	7.0	22.0
HT OP. WT.	388	745	1110	1570	2690	4085	5670	7595	790	16040
HT SHIP WT.	220	385	550	770	1210	1925	2750	3795	790	7040
VT OP. WT.	318	660	1060	1500	2630	3910	5470	7400	11650	15800
VT SHIP WT.	150	300	500	700	1150	1750	2550	3600	5250	6800



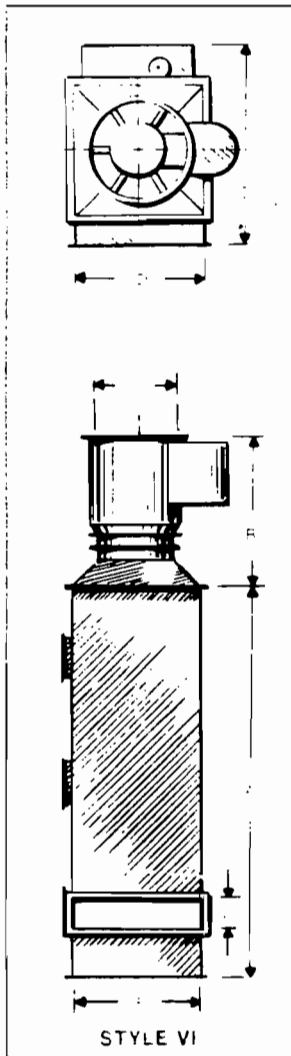


STYLE F H4

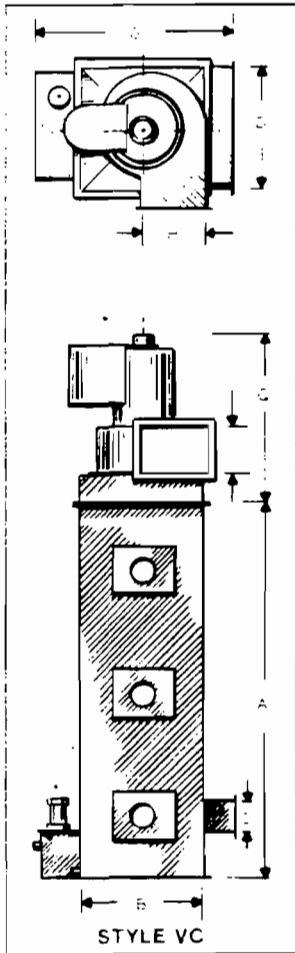


STYLE H

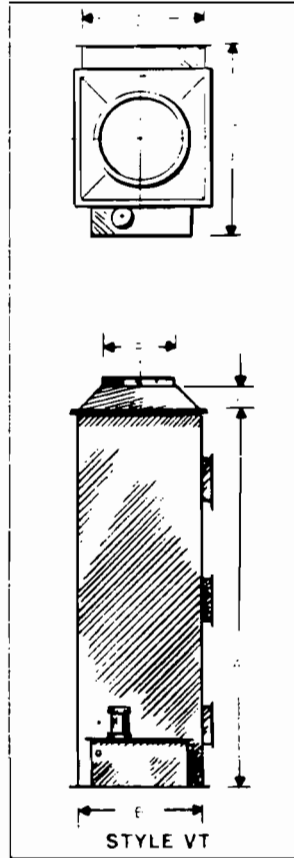
*May require one or more pumps.



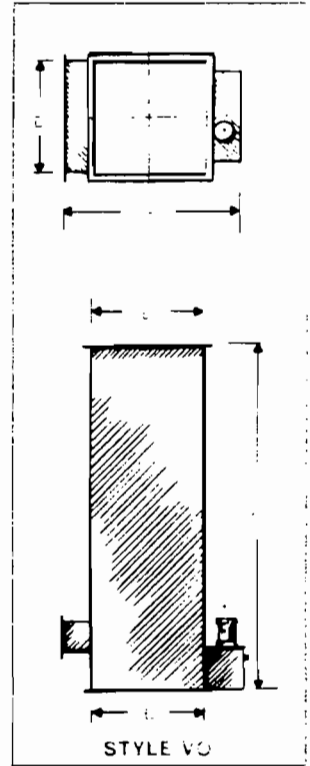
STYLE VI



STYLE VC



STYLE VT



STYLE VO

COMPUTERIZED PACKING MEDIA SELECTION

The most common mistake made by scrubber manufacturers today is the use of only one type of packing media for all types of contaminant removal. Beverly Pacific Corporation scrubbers are designed with a computer program assist to determine the most beneficial packing media to achieve high removal efficiency coupled with low pressure drop providing the user with the ultimate in lower operating costs consistent with the contaminant removal requirements.

SCRUBBER CONFIGURATIONS

Beverly Pacific Corporation manufactures scrubbers of both crossflow and counter-current configurations.

The CROSSFLOW design is of low profile, rectangular shape wherein the contaminated air stream moves horizontally through the packing media and is scrubbed by the liquid flowing downward through the packing. This configuration is ideal for roof-top mounting and is available in ten (10) standard sizes with or without integral centrifugal fans.

The COUNTER-CURRENT design is offered in two (2) configurations, round or rectangular. While the round tower unit is the most economical in initial cost, the rectangular tower unit permits larger CFM volume using the same amount of floor space. In the counter-current design, the contaminated airstream flows up through the packing media and is scrubbed by the liquid flowing downward. The round and rectangular tower units are each offered in ten (10) sizes and are available with or without integral inline or centrifugal fans.

SCRUBBER MAKE-UP WATER CONSUMPTION

Beverly Pacific's scrubber design is based on a scrubbing liquid recirculation rate of 5 GPM per 1000 CFM of contaminated air. Of that 5 GPM, losses due to absorption and/or evaporation range from 0.2 GPM to 0.6 GPM, depending on inlet gas temperature and gas stream dust load.

ENTRAINMENT SEPARATION

The unique design of Beverly Pacific's mist eliminator section provides up to 99+% moisture particle entrapment at a pressure drop of approximately 0.5" W.G.

CONSTRUCTION

The structural housings are fabricated of Fiberglass Reinforced Plastic (FRP) materials which provide structural strength, are corrosion-resistant and light in weight. Resin selection depends on the corrosive element involved. Resins can also be of fire-retardant grade if required. Our construction technique employs the use of female molds resulting in an extremely smooth, attractive, gelcoated exterior surface (note the upper right photo on the facing page). Beverly Pacific Corporation's construction methods meet or exceed the requirements of NBS-PS 15-69 for custom contact-molded reinforced polyester chemical resistant process equipment.

OPTIONAL EQUIPMENT, FITTINGS AND ACCESSORIES

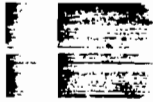
FITTINGS, such as drain, overflow, make-up water, access doors, etc. can usually be located to facilitate installation and maintenance.

RECIRCULATION RESERVOIR(S) are normally an integral part of the scrubber but, if required, can be furnished for remote installation.

RECIRCULATION PUMP(S) can be located within the built-in reservoir, but can also be installed in remote reservoir units.

SPECIAL RESERVOIR(S) can be furnished in applications where it is necessary to remove non-soluble particulate accumulation to prevent pump damage and minimize maintenance.

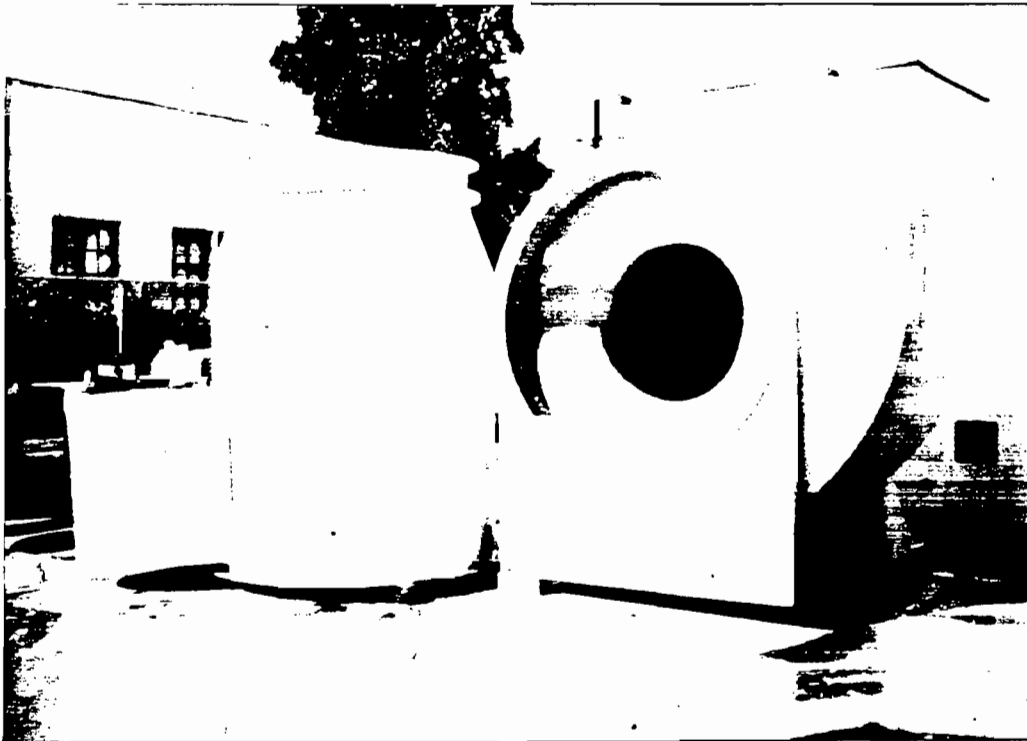
pH CONTROL SENSING/METERING equipment can be provided where contaminate absorption requires the addition of acid or caustic to the recirculated scrubbing liquid.



BEVERLY PACIFIC CORPORATION

Industrial Systems Division

EXHAUST FANS



FIBERGLASS REINFORCED PLASTIC

EXHAUST FAN INTRODUCTION

Beverly Pacific's complete line of centrifugal and inline exhaust fans have proven their reliability with years of successful, continuous corrosive service throughout the nation and around the world.

Our solid "FRP" construction defies corrosion and each is designed to provide smooth, quiet and maintenance-free operation . . . this superior combination permits peak performance with the lowest possible power consumption.

A wide selection of standard models, types and sizes are available to meet your specific requirements.

FAN WHEEL SUPERIORITY

The Beverly Pacific fan wheels are fabricated of corrosion-resistant Fiberglass Reinforced Plastic (FRP) materials. The fan wheel design is that of a "backward curve blade," Class II construction, and are available in standard sizes of 12 $\frac{1}{4}$ " through 66" diameters.

All of Beverly Pacific's fan wheels are both statically and dynamically balanced and run on a test stand prior to final assembly to insure continuous, vibration-free performance.

Every surface in contact with the air stream is corrosion resistant. The steel hub (providing the positive-lock connection to the drive shaft) is totally encapsulated in the wheel laminate and even the weight added during the wheel balancing process is corrosion resistant, Fiberglass Reinforced Plastic materials.

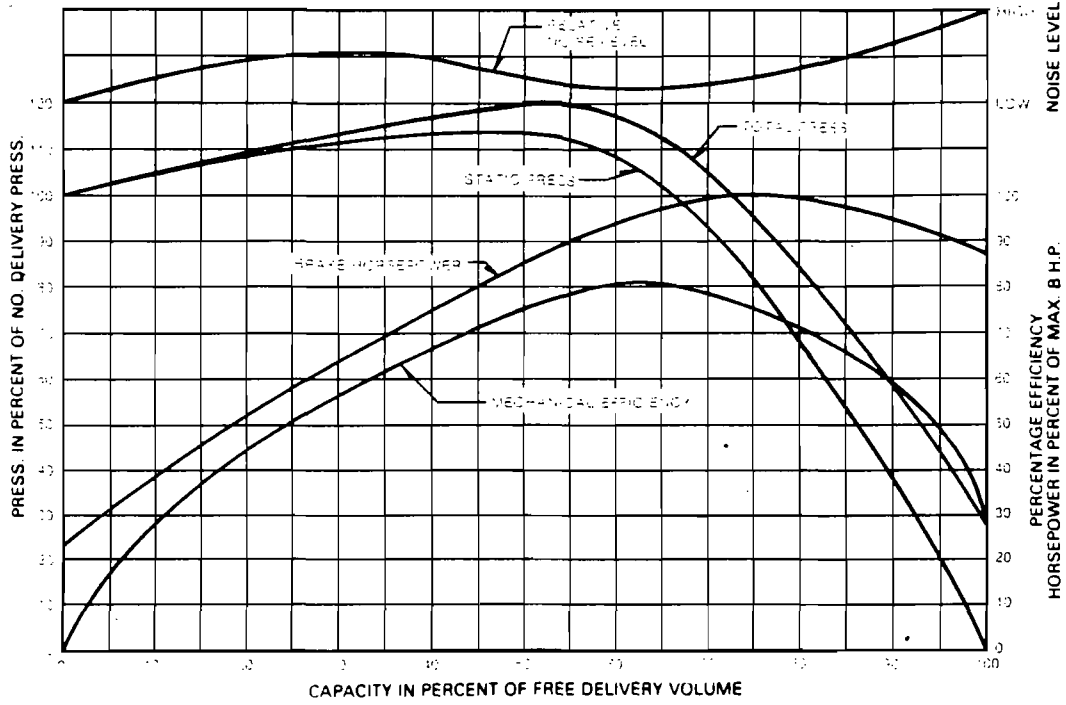
Should your particular requirement involve moving a volume of only a few hundred CFM at $\frac{1}{4}$ " S.P. or over 80,000 CFM at 6" S.P., Beverly Pacific has a proven standard size to meet your requirement.

EXHAUST FANS STANDARD AND OPTIONAL EQUIPMENT

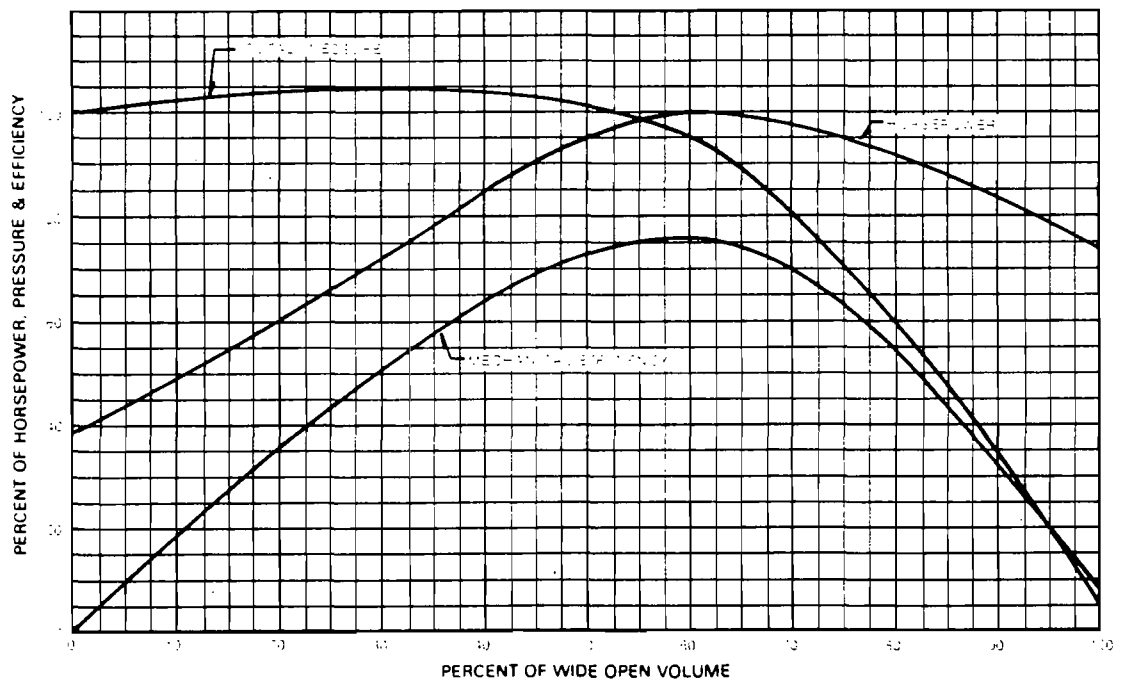
Standard Equipment: Beverly Pacific's centrifugal fans are equipped with a scroll bottom drain and flanged discharge outlet, and are furnished with a purchaser's choice of twelve (12) discharge outlet directions and a choice of right or left fan wheel rotation. Both of our fan styles, centrifugal and inline, are equipped with an OSHA approved belt guard and powered by 230-460/30/60 Hz motors . . . totally enclosed, fan-cooled, (TEFC) up to 20 horsepower, and Multi-guard motors are furnished when horsepower requirements are 25 or larger. Also, as standard equipment, Beverly Pacific furnishes the following list of first-line, top quality drive components which were selected based on motor horsepower, RPM, tip speed and weight of fan wheel, with a safety factor of 1.3 times the motor horsepower.

- a. BEARINGS — Beverly Pacific furnishes Dodge-Type K pillow blocks on the inline model. These Dodge bearings have Timken-tapered roller bearings, are fully self-aligning and designed to meet the stringent demands of power transmission. Based on radial and thrust load computations, bearing life expectancy is in excess of 100,000 hours.
- b. SHEAVES — Beverly Pacific Corporation furnishes Dodge sheaves, which are cast from the finest quality gray iron and machined to rigid quality control specifications. Groove design and spacing conforms to ASA, MPTA and RMA standards. These sheaves are equipped with Taper-Lock bushings, a superior mounting well recognized and widely used in industry.
- c. V-BELTS — Beverly Pacific furnishes Dodge Sealed-Life Belts, Type A, B and C which have a longer wearing protective cover, crowned top, concave sidewall, exceptional stability and an improved cord section which prevents failures caused by cord separation.
- d. WHEEL BACKING PLATES — Beverly Pacific uses Rex taper-lock, single-duty, Type B, steel sprocket, in the backing plate of all FRP fan wheels. This steel sprocket is completely embedded and encased with FRP materials to prevent corrosion attack.
- e. DRIVE SHAFTS — Beverly Pacific uses ground and polished, 1045 TGP shafting rounds, as produced by Inland Steel. This medium carbon steel is used because of its greater strength and hardness. The mechanical properties, based on $\frac{3}{4}$ " — 1 $\frac{1}{4}$ " diameter round bars of 1045, include a tensile strength of 98,000 PSI, yield strength of 59,000 PSI and a Brinell Hardness of 212.

BEVERLY PACIFIC CORPORATION CENTRIFUGAL FAN CHARACTERISTIC CURVE



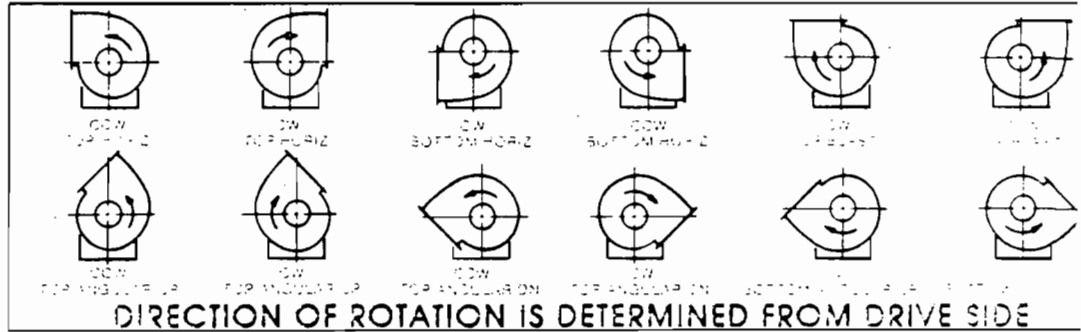
BEVERLY PACIFIC CORPORATION INLINE FAN CHARACTERISTIC CURVE



CENTRIFUGAL INDUSTRIAL EXHAUST FANS

	CB-12	CB-13	CB-15	CB-16	CB-18	CB-20	CB-22	CB-24	CB-27	CB-30	CB-33	CB-36
MID-RANGE CFM RECOMMENDED	2,150	2,625	3,200	3,900	4,750	5,800	7,075	8,650	10,550	12,875	15,700	19,700
FAN WHEEL DIAMETER	12 $\frac{1}{4}$	13 $\frac{1}{2}$	15	16 $\frac{1}{2}$	18 $\frac{1}{4}$	20	22 $\frac{1}{4}$	24 $\frac{1}{2}$	27	30	33	36
A	13 $\frac{1}{2}$	14 $\frac{1}{2}$	16 $\frac{1}{2}$	18 $\frac{1}{4}$	20	22	24 $\frac{1}{2}$	26	29 $\frac{1}{4}$	32 $\frac{1}{4}$	36	40
B	10 $\frac{3}{8}$	11 $\frac{3}{8}$	12 $\frac{3}{8}$	14 $\frac{3}{8}$	15	17	18 $\frac{3}{4}$	20 $\frac{1}{2}$	22 $\frac{3}{4}$	25	27	30
C	13 $\frac{3}{8}$	14 $\frac{3}{8}$	16 $\frac{3}{8}$	18 $\frac{3}{8}$	20	22 $\frac{1}{2}$	24	26 $\frac{1}{4}$	29 $\frac{1}{2}$	32	35 $\frac{1}{4}$	39
D	34 $\frac{1}{4}$	35 $\frac{1}{4}$	40 $\frac{1}{8}$	42 $\frac{1}{8}$	45	47 $\frac{1}{4}$	54	57 $\frac{1}{4}$	61 $\frac{1}{2}$	64 $\frac{1}{4}$	66 $\frac{3}{4}$	69
E	22 $\frac{1}{4}$	22 $\frac{1}{2}$	27 $\frac{1}{4}$	29 $\frac{1}{4}$	32 $\frac{3}{8}$	36 $\frac{1}{2}$	39 $\frac{1}{4}$	43 $\frac{1}{4}$	49	53	58 $\frac{3}{4}$	65
F	15	16	18	19	20	23	26	28	30	33	36	39
G	11	11 $\frac{1}{2}$	12 $\frac{1}{2}$	14	15 $\frac{1}{2}$	17 $\frac{1}{4}$	19	21 $\frac{1}{2}$	23	25 $\frac{1}{2}$	28 $\frac{1}{2}$	30
H	13 $\frac{3}{8}$	14 $\frac{3}{8}$	15 $\frac{3}{8}$	17 $\frac{3}{8}$	18	21	22 $\frac{3}{4}$	24 $\frac{1}{2}$	26 $\frac{3}{4}$	29	31	34
I	16	16	18 $\frac{1}{4}$	18 $\frac{3}{4}$	20	20 $\frac{1}{2}$	23	23	25	26	26	29
J	3	3	4	4	4	4	6	6	6	6	6	6
K	9 $\frac{1}{4}$	10 $\frac{1}{4}$	11 $\frac{1}{4}$	12 $\frac{1}{2}$	13 $\frac{1}{2}$	15	16	18	20 $\frac{1}{2}$	22	24	27
L	9 $\frac{1}{4}$	10 $\frac{1}{4}$	11 $\frac{1}{4}$	12 $\frac{1}{2}$	13 $\frac{1}{2}$	15	16	18	20 $\frac{1}{2}$	22	24	27
M	3 $\frac{1}{2}$	3 $\frac{3}{4}$	4 $\frac{1}{4}$	4 $\frac{1}{2}$	5	5 $\frac{1}{4}$	6 $\frac{3}{8}$	6 $\frac{3}{8}$	7 $\frac{1}{8}$	8 $\frac{1}{4}$	9 $\frac{1}{2}$	10
DRIVE SHAFT DIAMETER	1	1	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	2 $\frac{1}{16}$
SHIPPING WEIGHT POUNDS	170	205	230	400	550	600	650	720	850	1,000	1,380	1,700

DESIGNATION OF DIRECTION OF ROTATION AND DISCHARGE

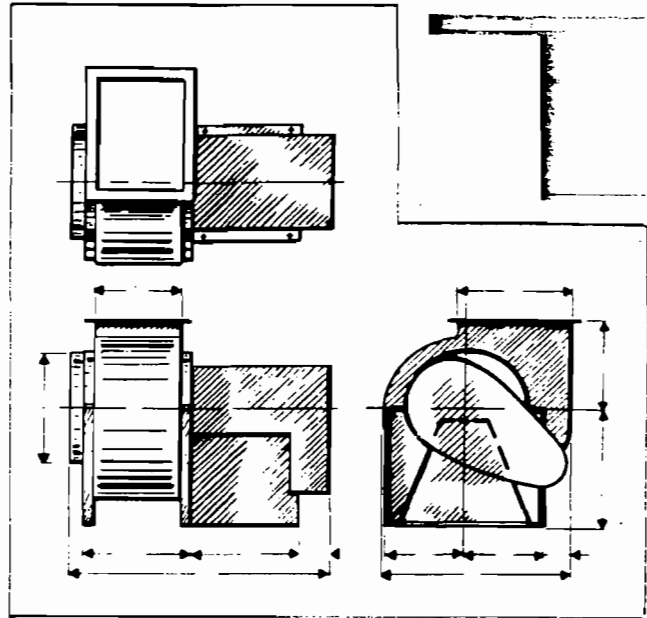


INLINE EXHAUST FANS

	IB-12	IB-15	IB-18	IB-20	IB-22	IB-24	IB-27	IB-30	IB-33	IB-36	IB-40	IB-44
MID-RANGE CFM RECOMMENDED	2,550	3,842	4,648	5,614	6,948	8,424	10,242	12,644	15,300	18,718	22,761	27,700
FAN WHEEL DIAMETER	12 $\frac{1}{4}$	15	18 $\frac{1}{4}$	20	22 $\frac{1}{4}$	24 $\frac{1}{2}$	27	30	33	36 $\frac{1}{2}$	40 $\frac{1}{2}$	44
P	21"	28"	32 $\frac{1}{2}$ "	36 $\frac{1}{2}$ "	40"	47"	53"	55"	58"	63 $\frac{3}{4}$ "	70"	76"
Q	14"	16"	20"	22"	24"	26"	30"	32"	36"	42"	46"	50"
R	18"	22"	26"	28"	32"	34"	38"	42"	45"	50"	56"	62"
S	2"	2"	2"	2"	2"	3"	3"	3"	3"	3"	3"	3"
T	23"	28"	31"	32"	34"	35"	37"	39"	40 $\frac{1}{2}$ "	45"	52"	63"
U	2"	2"	2"	2"	2"	3"	3"	3"	3"	3"	3"	3"
DRIVE SHAFT DIAMETER	1	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	1 $\frac{1}{16}$	2 $\frac{1}{16}$	2 $\frac{1}{16}$
SHIPPING WEIGHT POUNDS	90	130	290	320	350	380	450	525	730	850	1,110	1,400

DIMENSIONAL CHART

CB-36	CB-40	CB-44	CB-48	CB-54	CB-60	CB-66	
9.150	23,375	28,525	34,775	42,450	51,775	63,175	MID-RANGE CFM RECOMMENDED
16 1/2	40 1/4	44 1/2	49 1/2	54 1/4	60	66	FAN WHEEL DIAMETER
10	44 1/2	49	54 1/2	60	66	72	A
10	34 1/2	37 1/2	40 1/2	44 3/4	49 3/4	54 3/4	B
19	43	47 1/4	52 1/4	57 3/8	63 3/8	70 1/4	C
19 3/4	79 3/4	84 3/4	88 3/4	93	97 3/4	104 3/8	D
15 1/4	72 1/2	79 1/2	88 1/2	97	108	119	E
11 1/2	42	49 3/4	49 3/4	54	59	64	F
10 1/2	34 1/2	37 1/2	41	46	50 1/2	55	G
14	40 1/2	43 1/2	48 1/2	50 3/4	53 3/4	60 3/4	H
16	27 1/2	29 1/2	29 1/2	31 1/4	33	33	I
17	8	8	8	8	8	8	J
17	25 3/4	26 3/4	30 3/4	34	37	40	K
17	25 3/4	26 3/4	30 3/4	34	37	40	L
0 1/4	11 1/4	12 1/4	14 1/4	15 5/16	17 5/16	19 5/16	M
13 1/16	2 3/16	2 7/16	2 7/16	2 15/16	2 15/16	2 15/16	DRIVE SHAFT DIAMETER
610	2,050	2,300	2,600	3,110	3,525	4,000	SHIPPING WEIGHT POUNDS



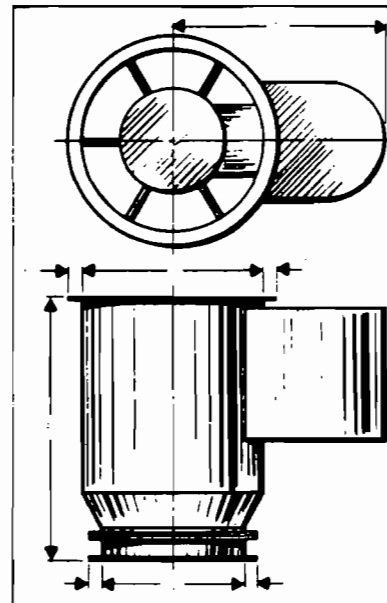
Bayley Pacific's FRP constructed fans have a Type "A" classification for spark resistance.

STANDARD CLASSIFICATIONS FOR SPARK RESISTANT CONSTRUCTION

TYPE	CONSTRUCTION
	All parts of the fan in contact with the air or gas being handled shall be made of non-ferrous material.
	The fan shall have an entirely non-ferrous wheel and non-ferrous ring about the opening through which the shaft passes.
	The fan shall be so constructed that a shift of the wheel or shaft will not permit two ferrous parts of the fan to rub or strike.

DIMENSIONAL CHART

IB-44	IB-48	IB-54	IB-60	IB-66	
7,822	33,733	41,349	50,579	61,201	MID-RANGE CFM RECOMMENDED
4 1/2	49	54 1/4	60	66	FAN WHEEL DIAMETER
9"	84"	93"	104"	116"	P
9"	54"	60"	66"	72"	Q
2"	66"	72"	80"	88"	R
	3"	3"	3"	3"	S
3"	65"	68"	72"	76"	T
	3"	3"	3"	3"	U
7/16	2 7/16	2 15/16	2 15/16	2 15/16	DRIVE SHAFT DIAMETER
250	1,420	1,650	1,800	2,100	SHIPPING WEIGHT POUNDS



CENTRIFUGAL CAPACITY RATING TABLES



DATA ON WHITE BACKGROUND APPLIES TO CLASS I WHEELS
DATA ON BLUE BACKGROUND APPLIES TO CLASS II WHEELS

CB-40



Table with 11 columns: Volume of air (CFM), 1" S.P., 1.5" S.P., 2" S.P., 2.5" S.P., 3" S.P., 3.5" S.P., 4" S.P., 4.5" S.P., 5" S.P., 5.5" S.P. Contains capacity data for various inlet diameters (40" and 44") and flow rates.

WHEEL 40" DIA
INLET 44" DIA
CLASS I MAX RPM 880
II 1120

Continuation of the CB-40 table with 10 columns for higher suction pressures (6" S.P. to 6.5" S.P.).

CB-44



Table with 11 columns: Volume of air (CFM), 1" S.P., 1.5" S.P., 2" S.P., 2.5" S.P., 3" S.P., 3.5" S.P., 4" S.P., 4.5" S.P., 5" S.P., 5.5" S.P. Contains capacity data for various inlet diameters (44" and 49") and flow rates.

WHEEL 44" DIA
INLET 49" DIA
CLASS I MAX RPM 825
II 1015

Continuation of the CB-44 table with 10 columns for higher suction pressures (6" S.P. to 6.5" S.P.).

CB-49

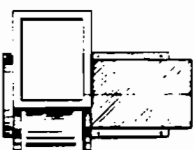


Table with 11 columns: Volume of air (CFM), 1" S.P., 1.5" S.P., 2" S.P., 2.5" S.P., 3" S.P., 3.5" S.P., 4" S.P., 4.5" S.P., 5" S.P., 5.5" S.P. Contains capacity data for various inlet diameters (49" and 54") and flow rates.

WHEEL 49" DIA
INLET 54" DIA
CLASS I MAX RPM 725
II 920

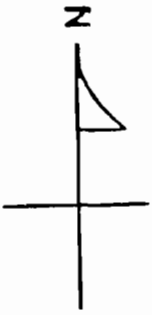
Continuation of the CB-49 table with 10 columns for higher suction pressures (6" S.P. to 6.5" S.P.).

USE CAPACITY TABLES AS GUIDE ONLY

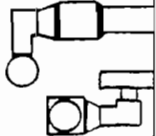


HARRIS SEMICONDUCTOR
AIR PERMIT – BUILDING 59
ATTACHMENT E
MAPS

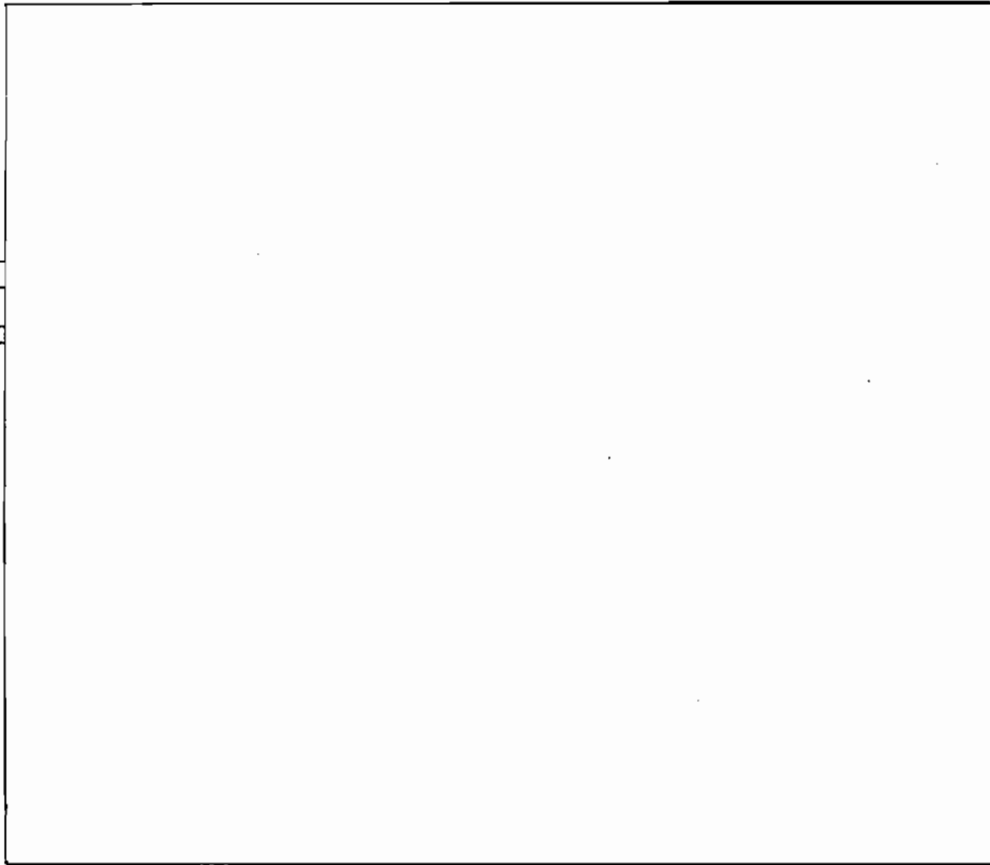
HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 59









F59S01



F59S03



LEGEND

- | | |
|---|------------------------|
|  | - Horizontal Scrubber |
|  | - Vertical Scrubber |
|  | - Exhaust Stack |
|  | - Exhaust Fan |
|  | - Stack mounted on fan |
|  | - Epitaxial Scrubber |

APOLLO BLVD

Harris Semiconductor Complex

SCRUBBER LOCATIONS

POND

F62S02
F62S01

62B

62A

PARKING LOT

F58S02
F58S01

58

F57S01

PARKING LOT

POND

PARKING LOT

59

F59S01
F59S03

63

F63S02
F63S01
F63S03

F54S03
F54S04
F54S01
F54S02

60

F60S01
F55S01

55

BORROW PIT

52

53

56

51

PARKING LOT

PARKING LOT

F04S05
F04S06
F04S01

6

TROUTMAN

F51S01
F51S02
F51S03
F51S04
F51S05

F04S08
F04S04
F04S03
F04S02

F61S02
F61S01

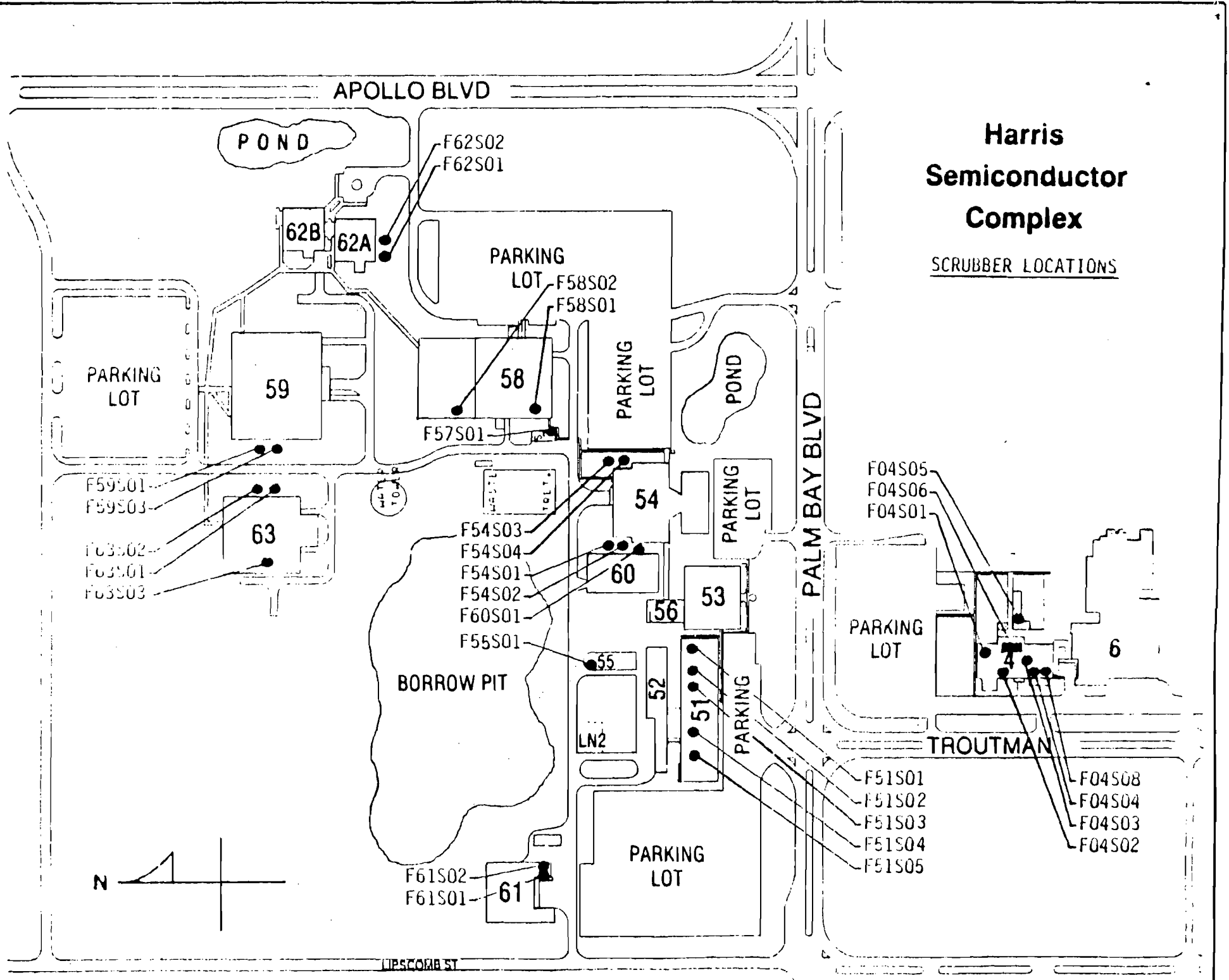
61

PARKING LOT

N

LIPSCOMB ST

PALM BAY BLVD





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DER-BAQM

FS-JRK-139-88

March 2, 1988

Mr. C. H. Fancy
Deputy Bureau Chief
Department of Environmental Regulation
Bureau of Air Quality Management
2600 Blair Stone Road
Tallahassee, Florida 32301

Reference: HARRIS SEMICONDUCTOR
B-54 Consolidated Air Permit

Dear Mr. Fancy:

On February 17, 1988, representatives from Harris and the Florida DER met in Orlando to discuss the status of air permits at Harris Semiconductor's facility in Palm Bay. At that meeting it was agreed that Harris would submit modified air permits. The purpose of the permit modifications was as follows:

1. Consolidate permits on a by building basis to reduce the existing number of permits.
2. To accurately quantify the current air emissions.

Enclosed is the modified permit application for Semiconductor's Building 54.

If you should have any questions about the enclosed information, please feel free to contact me at (305) 724-7467.

Sincerely,

J. R. Kolanek, Manager
Environmental Services

/pgc

cc: A. T. Sawicki
L. R. Hutker
D. R. Erdley
R. R. Sands

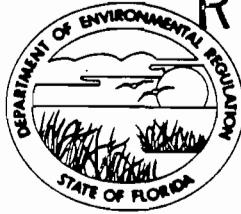
DEPARTMENT OF ENVIRONMENTAL REGULATION

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MAR 3 1988

BOB GRAHAM
GOVERNORVICTORIA J. TSCHINKEL
SECRETARY

DER-BAQM

WIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241

APPLICATION TO OPERATE/CONSTRUCT AIR POLLUTION SOURCES

SOURCE TYPE: Stationary New¹ Existing¹APPLICATION TYPE: Construction Operation ModificationCOMPANY NAME: HARRIS SEMICONDUCTOR COUNTY: BrevardIdentify the specific emission point source(s) addressed in this application (i.e. Lime
Kila No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired) B-54 Manufacturing FabSOURCE LOCATION: Street Palm Bay Road City Palm BayUTM: East 17-538700 North 17-3100900Latitude 28 ° 01 ' 20 "N Longitude 80 ° 36 ' 10 "WAPPLICANT NAME AND TITLE: J. R. Kolanek, Manager Environmental ServicesAPPLICANT ADDRESS: P.O. Box 883, Melbourne, Florida 32901

SECTION I: STATEMENTS BY APPLICANT AND ENGINEER

A. APPLICANT

I am the undersigned owner or authorized representative* of HARRIS SEMICONDUCTOR

I certify that the statements made in this application for a modified permit are true, correct and complete to the best of my knowledge and belief. Further, I agree to maintain and operate the pollution control source and pollution control facilities in such a manner as to comply with the provision of Chapter 403, Florida Statutes, and all the rules and regulations of the department and revisions thereof. I also understand that a permit, if granted by the department, will be non-transferable and I will promptly notify the department upon sale or legal transfer of the permitted establishment.

*Attach letter of authorization

Signed: James R. Kolanek
J. R. Kolanek, Manager, Environmental Services
Name and Title (Please Type)Date: 3-2-88 Telephone No. (305) 724-7467

B. PROFESSIONAL ENGINEER REGISTERED IN FLORIDA (where required by Chapter 471, F.S.)

This is to certify that the engineering features of this pollution control project have been designed/examined by me and found to be in conformity with modern engineering principles applicable to the treatment and disposal of pollutants characterized in the permit application. There is reasonable assurance, in my professional judgment, that

See Florida Administrative Code Rule 17-2.100(57) and (104)

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the pollution control facilities, when properly maintained and operated, will discharge an effluent that complies with all applicable statutes of the State of Florida and the rules and regulations of the department. It is also agreed that the undersigned will furnish, if authorized by the owner, the applicant a set of instructions for the proper maintenance and operation of the pollution control facilities and, if applicable, pollution sources.

Signed Lawrence R. Hutker

Lawrence R. Hutker

Name (Please Type)

HARRIS SEMICONDUCTOR

Company Name (Please Type)

P.O. Box 883, Melbourne, FL 32901

Mailing Address (Please Type)

Florida Registration No. 35972 Date: 3-2-88 Telephone No. (305) 729-4655

SECTION II: GENERAL PROJECT INFORMATION

A. Describe the nature and extent of the project. Refer to pollution control equipment, and expected improvements in source performance as a result of installation. State whether the project will result in full compliance. Attach additional sheet if necessary.

This is a modification and consolidation of existing air permits.

B. Schedule of project covered in this application (Construction Permit Application Only)

Start of Construction N/A Completion of Construction N/A

C. Costs of pollution control system(s): (Note: Show breakdown of estimated costs only for individual components/units of the project serving pollution control purposes. Information on actual costs shall be furnished with the application for operation permit.)

N/A

D. Indicate any previous DER permits, orders and notices associated with the emission point, including permit issuance and expiration dates.

A0 05-65408 issued 5/3/83 expires 5/2/88

A0 05-115804 issued 5/20/86 expires 5/22/91

E. Requested permitted equipment operating time: hrs/day 24; days/wk 7; wks/yr 52; if power plant, hrs/yr _____; if seasonal, describe: _____

F. If this is a new source or major modification, answer the following questions. (Yes or No)

1. Is this source in a non-attainment area for a particular pollutant? No
a. If yes, has "offset" been applied? _____
b. If yes, has "Lowest Achievable Emission Rate" been applied? _____
c. If yes, list non-attainment pollutants. _____

2. Does best available control technology (BACT) apply to this source? No
If yes, see Section VI.

3. Does the State "Prevention of Significant Deterioration" (PSD) requirement apply to this source? If yes, see Sections VI and VII. No

4. Do "Standards of Performance for New Stationary Sources" (NSPS) apply to this source? No

5. Do "National Emission Standards for Hazardous Air Pollutants" (NESHAP) apply to this source? No

H. Do "Reasonably Available Control Technology" (RACT) requirements apply to this source? No

a. If yes, for what pollutants? _____

b. If yes, in addition to the information required in this form, any information requested in Rule 17-2.650 must be submitted.

Attach all supportive information related to any answer of "Yes". Attach any justification for any answer of "No" that might be considered questionable.

SECTION III: AIR POLLUTION SOURCES & CONTROL DEVICES (Other than Incinerators)

A. Raw Materials and Chemicals Used in your Process, if applicable:

Description	Contaminants		Utilization Rate - lbs/hr	Relate to Flow Diagram
	Type	% Wt		
SEE ATTACHMENT	C			

B. Process Rate, if applicable: (See Section V, Item 1)

- Total Process Input Rate (lbs/hr): not applicable
- Product Weight (lbs/hr): not applicable

C. Airborne Contaminants Emitted: (Information in this table must be submitted for each emission point, use additional sheets as necessary)

Name of Contaminant	Emission ¹		Allowed Emission Rate per Rule 17-2	Allowable ³ Emission lbs/hr	Potential ⁴ Emission		Relate to Flow Diagram
	Maximum lbs/hr	Actual T/yr			lbs/yr	T/yr	
SEE ATTACHMENT B							

¹See Section V, Item 2.

²Reference applicable emission standards and units (e.g. Rule 17-2.600(5)(b)2. Table II, E. (1) - 0.1 pounds per million BTU heat input)

³Calculated from operating rate and applicable standard.

⁴Emission, if source operated without control (See Section V, Item 3).

J. Control Devices: (See Section V, Item 4)

Name and Type (Model & Serial No.)	Contaminant	Efficiency	Range of Particles Size Collected (in microns) (If applicable)	Basis for Efficiency (Section V Item 5)
SEE ATTACHMENT D				

E. Fuels not applicable

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	avg/hr	max./hr	

*Units: Natural Gas--MMCF/hr; Fuel Oils--gallons/hr; Coal, wood, refuse, other--lbs/hr.

Fuel Analysis:

Percent Sulfur: _____ Percent Ash: _____
 Density: _____ lbs/gal Typical Percent Nitrogen: _____
 Heat Capacity: _____ BTU/lb _____ BTU/gal
 Other Fuel Contaminants (which may cause air pollution): _____

F. If applicable, indicate the percent of fuel used for space heating.

Annual Average _____ Maximum _____

G. Indicate liquid or solid wastes generated and method of disposal.

Waste water from air scrubbers is discharged to on-site waste water treatment plant.
 Discharge to deep well under UIC-Permit #UC05-126519.

SEE ATTACHEMENT D

H. Emission Stack Geometry and Flow Characteristics (Provide data for each stack):

Stack Height: _____ ft. Stack Diameter: _____ ft.
 Gas Flow Rate: _____ ACFM _____ DSCFM Gas Exit Temperature: _____ °F.
 Water Vapor Content: _____ % Velocity: _____ FPS

SECTION IV: INCINERATOR INFORMATION
 not applicable

Type of Waste	Type 0 (Plastics)	Type I (Rubbish)	Type II (Refuse)	Type III (Garbage)	Type IV (Pathological)	Type V (Liq. & Gas By-prod.)	Type VI (Solid By-prod.)
Actual lb/hr Incinerated							
Uncontrolled (lbs/hr)							

Description of Waste _____

Total Weight Incinerated (lbs/hr) _____ Design Capacity (lbs/hr) _____

Approximate Number of Hours of Operation per day _____ day/wk _____ wks/yr. _____

Manufacturer _____

Date Constructed _____ Model No. _____

	Volume (ft) ³	Heat Release (BTU/hr)	Fuel		Temperature (°F)
			Type	BTU/hr	
Primary Chamber					
Secondary Chamber					

Stack Height: _____ ft. Stack Diameter: _____ Stack Temp. _____

Gas Flow Rate: _____ ACFM _____ DSCFM* Velocity: _____ FPS

*If 50 or more tons per day design capacity, submit the emissions rate in grains per standard cubic foot dry gas corrected to 50% excess air.

Type of pollution control device: Cyclone Wet Scrubber Afterburner
 Other (specify) _____

Brief description of operating characteristics of control devices: _____

Ultimate disposal of any effluent other than that emitted from the stack (scrubber water, ash, etc.):

NOTE: Items 2, 3, 4, 6, 7, 8, and 10 in Section V must be included where applicable.

SECTION V: SUPPLEMENTAL REQUIREMENTS

Please provide the following supplements where required for this application.

1. Total process input rate and product weight -- show derivation [Rule 17-2.100(127)]
2. To a construction application, attach basis of emission estimate (e.g., design calculations, design drawings, pertinent manufacturer's test data, etc.) and attach proposed methods (e.g., FR Part 60 Methods 1, 2, 3, 4, 5) to show proof of compliance with applicable standards. To an operation application, attach test results or methods used to show proof of compliance. Information provided when applying for an operation permit from a construction permit shall be indicative of the time at which the test was made.
3. Attach basis of potential discharge (e.g., emission factor, that is, AP42 test).
4. With construction permit application, include design details for all air pollution control systems (e.g., for baghouse include cloth to air ratio; for scrubber include cross-section sketch, design pressure drop, etc.)
5. With construction permit application, attach derivation of control device(s) efficiency. Include test or design data. Items 2, 3 and 5 should be consistent: actual emissions = potential (1-efficiency).
6. An 8 1/2" x 11" flow diagram which will, without revealing trade secrets, identify the individual operations and/or processes. Indicate where raw materials enter, where solid and liquid waste exit, where gaseous emissions and/or airborne particles are evolved and where finished products are obtained.
7. An 8 1/2" x 11" plot plan showing the location of the establishment, and points of airborne emissions, in relation to the surrounding area, residences and other permanent structures and roadways (Example: Copy of relevant portion of USGS topographic map).
8. An 8 1/2" x 11" plot plan of facility showing the location of manufacturing processes and outlets for airborne emissions. Relate all flows to the flow diagram.

9. The appropriate application fee in accordance with Rule 17-4.05. The check should be made payable to the Department of Environmental Regulation.
10. With an application for operation permit, attach a Certificate of Completion of Construction indicating that the source was constructed as shown in the construction permit.

SECTION VI: BEST AVAILABLE CONTROL TECHNOLOGY

A. Are standards of performance for new stationary sources pursuant to 40 C.F.R. Part 60 applicable to the source?

Yes No

Contaminant	Rate or Concentration

B. Has EPA declared the best available control technology for this class of sources (If yes, attach copy)

Yes No

Contaminant	Rate or Concentration

C. What emission levels do you propose as best available control technology?

Contaminant	Rate or Concentration

D. Describe the existing control and treatment technology (if any).

- | | |
|---------------------------|--------------------------|
| 1. Control Device/System: | 2. Operating Principles: |
| 3. Efficiency:* | 4. Capital Costs: |

*Explain method of determining

5. Useful Life:

6. Operating Costs:

7. Energy:

8. Maintenance Cost:

9. Emissions:

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

10. Stack Parameters

a. Height:

ft.

b. Diameter:

ft.

c. Flow Rate:

ACFM

d. Temperature:

°F.

e. Velocity:

FPS

E. Describe the control and treatment technology available (As many types as applicable, use additional pages if necessary).

1.

a. Control Device:

b. Operating Principles:

c. Efficiency:¹

d. Capital Cost:

e. Useful Life:

f. Operating Cost:

g. Energy:²

h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

2.

a. Control Device:

b. Operating Principles:

c. Efficiency:¹

d. Capital Cost:

e. Useful Life:

f. Operating Cost:

g. Energy:²

h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

¹Explain method of determining efficiency.

²Energy to be reported in units of electrical power - KWH design rate.

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

3.

a. Control Device:

b. Operating Principles:

c. Efficiency:¹

d. Capital Cost:

e. Useful Life:

f. Operating Cost:

g. Energy:²

h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

4.

a. Control Device:

b. Operating Principles:

c. Efficiency:¹

d. Capital Costs:

e. Useful Life:

f. Operating Cost:

g. Energy:²

h. Maintenance Cost:

i. Availability of construction materials and process chemicals:

j. Applicability to manufacturing processes:

k. Ability to construct with control device, install in available space, and operate within proposed levels:

F. Describe the control technology selected:

1. Control Device:

2. Efficiency:¹

3. Capital Cost:

4. Useful Life:

5. Operating Cost:

6. Energy:²

7. Maintenance Cost:

8. Manufacturer:

9. Other locations where employed on similar processes:

a. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

¹ Explain method of determining efficiency.

Energy to be reported in units of electrical power - KWH design rate.

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant	Rate or Concentration

(8) Process Rate:¹

b. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant	Rate or Concentration

(8) Process Rate:¹

10. Reason for selection and description of systems:

¹Applicant must provide this information when available. Should this information not be available, applicant must state the reason(s) why.

SECTION VII - PREVENTION OF SIGNIFICANT DETERIORATION not applicable

A. Company Monitored Data

1. _____ no. sites _____ TSP () SO₂* _____ Wind spd/dir

Period of Monitoring _____ / _____ / _____ to _____ / _____ / _____
month day year month day year

Other data recorded _____

Attach all data or statistical summaries to this application.

Specify bubbler (B) or continuous (C).

2. Instrumentation, Field and Laboratory

- a. Was instrumentation EPA referenced or its equivalent? Yes No
- b. Was instrumentation calibrated in accordance with Department procedures?
 Yes No Unknown

B. Meteorological Data Used for Air Quality Modeling

- 1. _____ Year(s) of data from _____ / _____ / _____ to _____ / _____ / _____
month day year month day year
- 2. Surface data obtained from (location) _____
- 3. Upper air (mixing height) data obtained from (location) _____
- 4. Stability wind rose (STAR) data obtained from (location) _____

C. Computer Models Used

- 1. _____ Modified? If yes, attach description.
- 2. _____ Modified? If yes, attach description.
- 3. _____ Modified? If yes, attach description.
- 4. _____ Modified? If yes, attach description.

Attach copies of all final model runs showing input data, receptor locations, and principle output tables.

D. Applicants Maximum Allowable Emission Data

Pollutant	Emission Rate
TSP	_____ grams/sec
SO ²	_____ grams/sec

E. Emission Data Used in Modeling

Attach list of emission sources. Emission data required is source name, description of point source (on NEDS point number), UTM coordinates, stack data, allowable emissions, and normal operating time.

F. Attach all other information supportive to the PSD review.

G. Discuss the social and economic impact of the selected technology versus other applicable technologies (i.e., jobs, payroll, production, taxes, energy, etc.). Include assessment of the environmental impact of the sources.

H. Attach scientific, engineering, and technical material, reports, publications, journals, and other competent relevant information describing the theory and application of the requested best available control technology.

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT A

Process Description

Attachment A

Building 54 is a wafer fabrication facility. The second floor of the two-story building houses two clean room modules. Both fabrication areas employ a series of manufacturing procedures referred to as layering, patterning, doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

In the controlled environment of the fabrication clean rooms, wafer surfaces first undergo acid and/or solvent cleaning, followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process, the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "alligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques.

In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Additional material may be layered on the wafer surface in vapor and crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation.

Wet stations that house vats containing a variety of acid and caustic compounds are located throughout the clean rooms. Storage cabinets safely hold virgin chemicals until they are ready for use. The first floor of the building contains exhausted gas cabinets that supply process gases to the 'fab' operations.

The exhaust system for the building is divided into two sections. The west half exhaust is fed into a common duct that is divided into two wet scrubber systems, F54S01 and F54S02, at ground level. The east portion of the building exhaust is ducted a common line that divides into two wet scrubbers (F54S03 and F54S04) on the east side of building (see attachment E.) Also on the east side of building 54 is a non-scrubbed exhaust fan F54E17 that handles air flow from several alligners, furnace source cabinets, and gas cabinets.

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT B

Air Emissions

Attachment B

Monitoring work was performed on the building 54 scrubber systems in August and November of 1987. Tests conducted included EPA methods 25A (flame ionization detector) and TO-1 (Tenax adsorption and GC/MS analysis.) The results of this testing is included in this application.

FID test results revealed that total accumulative monitored VOC emissions for the building were 82.58 tons/year expressed as propane. This figure includes off-shift emissions and is based on a 8760 day a year production schedule for the east fab and a 4160 day a year production schedule for the west. The following assumptions were made regarding monitoring work on this building:

- Emission values for F54S02 & F54S04 are assumed to be equal to F54S01 & F54S03, respectively. This is because each pair handle exhaust from a common duct.
- VOC values refer to all organic emissions including organic solvents.
- Nonproduction emissions are assumed to be 18.3% of production emissions, as was found to be the case when scrubber F54S01 was monitored on a day of no production in the fabrication area.
- Nonproduction emissions are based on a 13% scrubber removal efficiency.
- All data is corrected for 2 ppm background concentration of VOC's that is present in the ambient air.
- The F.I.D. accumulative emission figure is based on the maximum concentration observed during the monitoring timeframe.

Total projected VOC emissions for building 54 is 94.34 tons/year. This number is representative of maximum VOC emissions, and is derived from the following proportion:

$$\begin{array}{r} \frac{82.58 \text{ tpy}}{131.29 \text{ tpy}} - \frac{94.34 \text{ tpy}}{150.00 \text{ tpy}} \end{array}$$

- where:
- 82.58 tpy is the maximum building emissions determined by EPA Method 25-A monitoring.
 - 131.29 tpy is the maximum Semiconductor site emissions determined by EPA Method 25-A monitoring.
 - 150.00 tpy is the established site emission limit for VOC's.

EPA METHOD 25-A (F.I.D. ANALYSIS) BUILDING 54
EMISSIONS DURING PRODUCTION HOURS

TEST DATE	F54S01 (TON/YR)	F54S02 (TON/YR)	F54S03 (TON/YR)	F54S04 (TON/YR)
08/20/87	5.36	5.36	---	---
08/21/87	---	---	25.4	25.4
11/14/87	---	---	30.22	30.22
11/22/87	---	---	32.59	32.59
11/23/87	7.24	7.24	---	---

NOTE: ABOVE BASED ON ACTUAL OPERATING HOURS.

TOTAL VOC EMISSIONS FROM BUILDING 54
AS DETECTED BY EPA METHOD 25-A

SCRUB#	PRODUCTN SCHEDULE	NONPRODUCTN SCHEDULE	PRODUCTN EMISSIONS (TON/YR)	NONPRODUCTN EMISSIONS (TON/YR)	TOTAL MONITORED VOC EMISSIONS* (TON/YR)
F54S01	4160	4600	7.24	1.47	8.70
F54S02	4160	4600	7.24	1.47	8.70
F54S03	8760	0	32.59	0	32.59
F54S04	8760	0	32.59	0	32.59

* BASED ON MAXIMUM CONCENTRATIONS OBSERVED.

TOTAL PROJECTED VOC EMISSIONS FOR BLDG. 54 - 94.34 TONS/YEAR

EPA METHOD TO-1: GC/MS ANALYSIS

AUGUST RESULTS-

	-----SCRUBBER #-----			
	F54S01	F54S02	F54S03	F54S04
ACETONE (LB/HR)	1.23	1.23	3.18	3.18
TRICHLOROETHANE (LB/HR)	---	---	0.33	0.33
METHYLENE CHLORIDE (LB/HR)	trace	trace	---	---
TETRACHLOROMETHYLENE (LB/HR)	---	---	0.17	0.17
FREON-113 (LB/HR)	0.02	0.02	0.07	0.07
CHLOROFORM (LB/HR)	trace	trace	---	---
BENZENE (LB/HR)	trace	trace	trace	trace
TRICHLOROETHYLENE (LB/HR)	trace	trace	trace	trace
TOLUENE (LB/HR)	trace	trace	trace	trace
METHYL ISOBUTYL KETONE (LB/HR)	---	---	---	---
ETHYL BENZENE (LB/HR)	---	---	---	---
XYLENES (LB/HR)	---	---	---	---

NOVEMBER RESULTS-

	F54S01	F54S02	F54S03	F54S04
ACETONE (LB/HR)	---	---	2.10	2.10
XYLENES (LB/HR)	---	---	0.66	0.66
ETHYL BENZENE (LB/HR)	---	---	0.15	0.15
1,2-DICHLOROBENZENE (LB/HR)	---	---	0.85	0.85
1,1-DICHLOROETHENE (LB/HR)	---	---	0.07	0.07
TETRACHLOROETHENE (LB/HR)	---	---	2.02	2.02
1,1,1-TRICHLOROETHANE	---	---	6.10	6.10

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT C

Raw Materials and Chemicals

PROCESS CHEMICALS

1. ACETIC ACID
2. AMMONIUM FLUORIDE
3. AMMONIA
4. AMMONIUM HYDROXIDE
5. ETHYLENE GLYCOL
6. GLYCERINE
7. HYDROFLUORIC ACID
8. HYDROCHLORIC ACID
9. HYDROGEN PEROXIDE
10. NITRIC ACID
11. PHOSPHORIC ACID
12. POTASSIUM HYDROXIDE
13. SODIUM HYDROXIDE
14. SULFURIC ACID
15. CHROMIC ACID
16. TETRAMETHYL AMMONIUM HYDROXIDE
17. ETHYLENE DIAMINE TETRACETIC ACID (EDTA)
18. DODECYLBENZENE SULFONIC ACID
19. ALKYL ARYL SULFONIC ACID
20. CERIC SULFATE
21. SODIUM HYPOPHOSPHITE
22. PHOSPHATE
23. ALUMINA SILICA

PROCESS GASES

1. ARGON
2. ARSINE
3. BORON TRIBROMIDE
4. BORON TRICHLORIDE
5. BORON TRIFLUORIDE
6. CARBON DIOXIDE
7. CHLORINE
8. DIBORANE
9. DICHLOROSILANE
10. HELIUM
11. HYDROGEN CHLORIDE
12. HYDROGEN
13. NITROGEN
14. NITROGEN TRIFLUORIDE
15. NITROUS OXIDE
16. OXYGEN
17. PHOSPHINE
18. PHOSPHOROUS OXYCHLORIDE
19. PHOSPHOROUS TRIBROMIDE
20. SILANE
21. SULFUR HEXAFLUORIDE
22. TUNGSTEN HEXAFLUORIDE
23. DE 100
24. PDE 100

PROCESS CHEMICALS

SOLVENTS

1. 1,1,1 TRICHLOROETHANE
2. ACETONE
3. BUTYL CELLOSOLVE
4. CELLOSOLVE ACETATE
5. CARBON TETRACHLORIDE
6. FREON 116
7. FREON 14
8. FREON 23
9. FREON TF
10. HEXAMETHYLDISILIZANE
11. ISOPROPYL ALCOHOL
12. METHANOL
13. N-BUTYL ACETATE
14. XYLENE
15. ETHYL BENZENE
16. 2-ETHOXYETHYL ACETATE
17. 1,2,4 TRICHLOROBENZENE
18. AROMATIC PHENOL
19. CRESOL
20. OIL
21. ISOPARAFFINIC HYDROCARBONS
22. OXYLPHENOL POLYETHOXYLATE
23. PROPYLENE GLYCOL MONOETHYL ETHER ACETATE
24. 1,1,1 TRIMETHYL-N-TRIMETHYL ETHER
25. PHILTEC SAFETY STAIN

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT D

Control Equipment

SCRUBBER INFORMATION

HARRIS ID # : F54S01
MANUFACTURER : HARRISON MODEL NUMBER : HF-200
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 95 MAKE UP RATE (GPM): 9.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): NR MAKE UP RATE (GPM): 5 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : A. O. SMITH MODEL NUMBER : P48K2EB7B2
SERIAL NUMBER: N/A HP : 1 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : P

FAN INFORMATION

HARRIS ID # : F54E01
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-FP3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD INCLINED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 STATIC PRESS (IN): 3.3

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 30 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : U

SCRUBBER INFORMATION

HARRIS ID # : F54502
MANUFACTURER : HARRISON MODEL NUMBER : HF-200
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 95 MAKE UP RATE (GPM): 9.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): 30 MAKE UP RATE (GPM): 5.0 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FRANKLIN ELECTRIC MODEL NUMBER : 1303012101
SERIAL NUMBER: N/A HP : 1/2 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : P

FAN INFORMATION

HARRIS ID # : F54E02
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-FP3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD CURVED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 STATIC PRESS (IN): 3.3

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 30 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : U

SCRUBBER INFORMATION

HARRIS ID # : F54S03
MANUFACTURER : HARRISON MODEL NUMBER : HF-230
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 23,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 112 MAKE UP RATE (GPM): 11

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): 30 MAKE UP RATE (GPM): 10 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : GENERAL ELECT. MODEL NUMBER : 5KFG2666
SERIAL NUMBER: HP : 1/3 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S,I

FAN INFORMATION

HARRIS ID # : F54E12
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-GS3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD CURVED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 26,500 STATIC PRESS (IN): 5.6

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 40 RPM : 1287
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S,U

SCRUBBER INFORMATION

HARRIS ID # : F54S04
MANUFACTURER : HARRISON MODEL NUMBER : HF-230
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 23,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 112 MAKE UP RATE (GPM): 11

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): 70 MAKE UP RATE (GPM): 10 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : GENERAL ELECT. MODEL NUMBER : 5K42FG2666
SERIAL NUMBER: N/A HP : 1/3 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S,I

FAN INFORMATION

HARRIS ID # : F54E13
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-GS3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD CURVED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 26,500 STATIC PRESS (IN): 5.6

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 40 RPM : 1287
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S,U

Attachment :

Plastic Packed Scrubbers



THE HARRISON SYSTEM

Harrison is a prime designer and producer of complete plastic exhaust systems, custom engineered scrubbing systems, as well as duct and fittings, tanks, and hoods. As a result of this capability and experience, design and manufacture of standard, pre-engineered fume scrubbers is a natural extension.

MATERIALS

Self-supporting or fiberglass armored PVC and Polypropylene, fiberglass armored Kynar, and solid fiberglass construction offers a wide range of resistance to acids, alkalis, solvents, and other corrosives at operating temperatures to approximately 250°F. Harrison systems do not use any metal in contact with the process stream.

PRE-ENGINEERING

Pre-engineered design reduces cost by eliminating the necessity to re-invent each item ordered. It results in more reliable service thru improved workmanship achieved by repetitive production control, and speeds quotations and approval drawings because costs and designs are immediately available. In addition to significant savings in approval and order time, Harrison reduces delivery time by stocking scrubber components including packing, support grids, distributor plates, nozzles, duct reducers, and sheet stock.

SCRUBBER CONFIGURATION

Most fume removal applications can be served by the two scrubber designs shown in this catalog. Vertical Counter Current style directs liquid down vertically, and unwanted fumes upward in the opposite direction. Horizontal Cross Flow unit directs liquid down vertically, but unwanted fumes are driven horizontally at 90° to the liquid. In both designs, liquid and fumes are inter-mixed in the packed bed section of the scrubber where fumes are removed by chemical reaction or water solubility. Scrubber shape does not affect performance. Horizontal design presents a low profile and is suitable where head room is limited. Verticals require more head room, but use only minimum floor space.

SCRUBBER DESIGN AND OPERATION

Highest scrubber efficiency (volumetric % of contaminate removed) is obtained by having the proper amount of contact surface area (packing) wetted by sufficient liquid (recirculated liquid rate) for an optimum residence time (packing depth) to allow unwanted fumes to take a treacherous path thru the wetted packing to permit their maximum removal from the carrier air stream by chemical reaction or water solubility.

Air stream resistance encountered in the packing (static pressure loss) is a function of air velocity, cross-sectional packing area, and packing depth. Harrison scrubbers utilize proven packing depth to achieve efficiencies approaching 99+%, when operated within recommendations.

LIQUID DISTRIBUTION AND MIST ELIMINATION

Simple liquid distribution is achieved thru a main header pipe feeding perforated laterals without use of troublesome spray nozzles. Nozzles are subject to plugging, and produce a difficult-to-remove atomized mist carryover. In the Harrison design, any large droplets of liquid caught in the upward moving air stream are easily and efficiently removed by a short bed of dry packing located above the liquid distributor.

STATIC PRESSURE LOSS

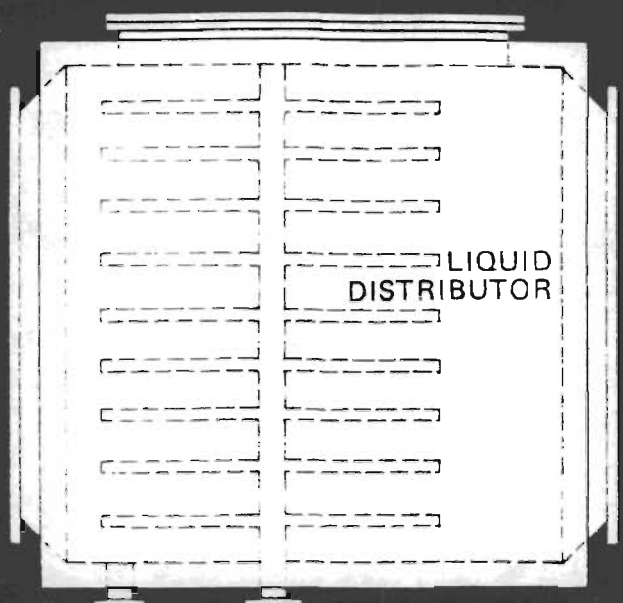
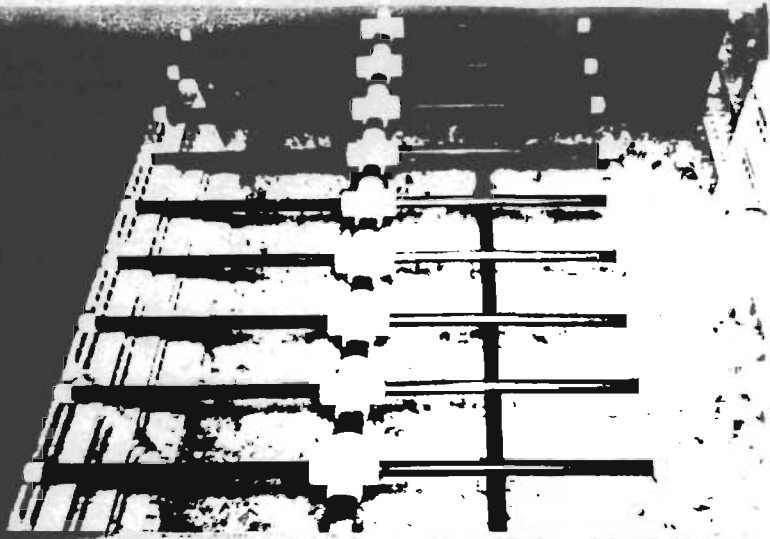
Use of high-surface-area, low-pressure-drop plastic saddles in a balanced design result in low static pressure loss of only 0.4 inches H₂O (w.g.) per foot of packed depth in Vertical Counter Current scrubbers, and 0.33 in Horizontal Cross Flow units. At the same time, sufficient irrigation rates constantly keep saddles clear of potential sludge buildup. Thereby, continuous, non-clogging operation at a proper rate of intermixing turbulence between liquid and fumes is achieved for 99+% efficiency.

LIQUID SUMP OPERATION

Harrison scrubbers employ an integral liquid recirculating sump which reduces amount of liquid consumption required by 90 to 95% in most applications. Therefore, considerably less effluent must be handled and treated. The sump reservoir is contained within the scrubber itself. Harrison recommends optimum rate of effluent removal. When effluent is acidic only, additional liquid conservation can be obtained with either scrubber design with the simple optional recovery system shown with the vertical scrubber drawing on page 4. If central treating facilities exist, no sump, recirculation, or independent recovery is needed. In this case, treated liquid would be directed over the packing in a single pass, then treated, then returned to the scrubber, etc. In both instances where effluent is treated, liquid consumption would be reduced to only that amount lost by evaporation.

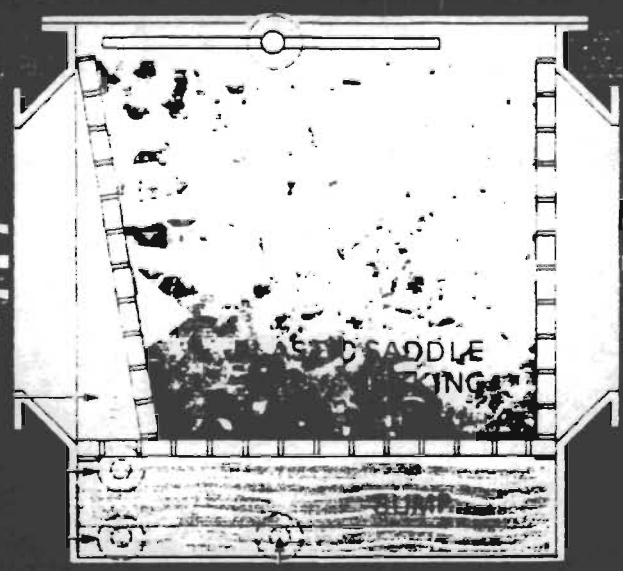
Harrison

Box 184 Aurora Ohio 44202/216-562-9545



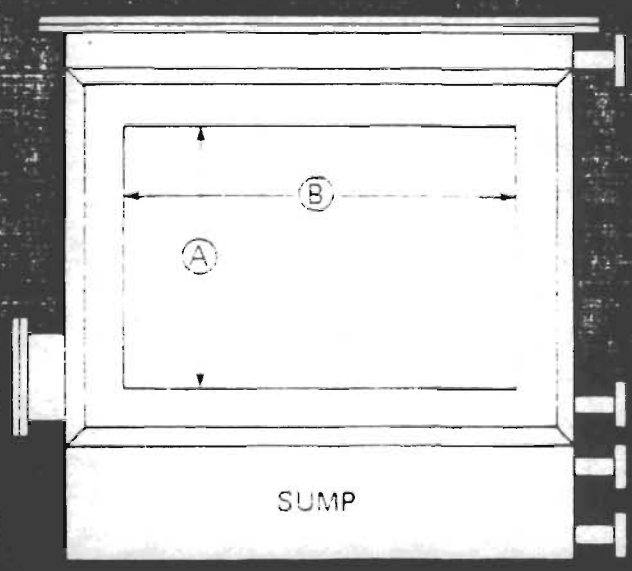
LIQUID DISTRIBUTOR

TOP VIEW



SADDLE

SIDE VIEW (CUT-A-WAY)



SUMP

INLET SIDE VIEW

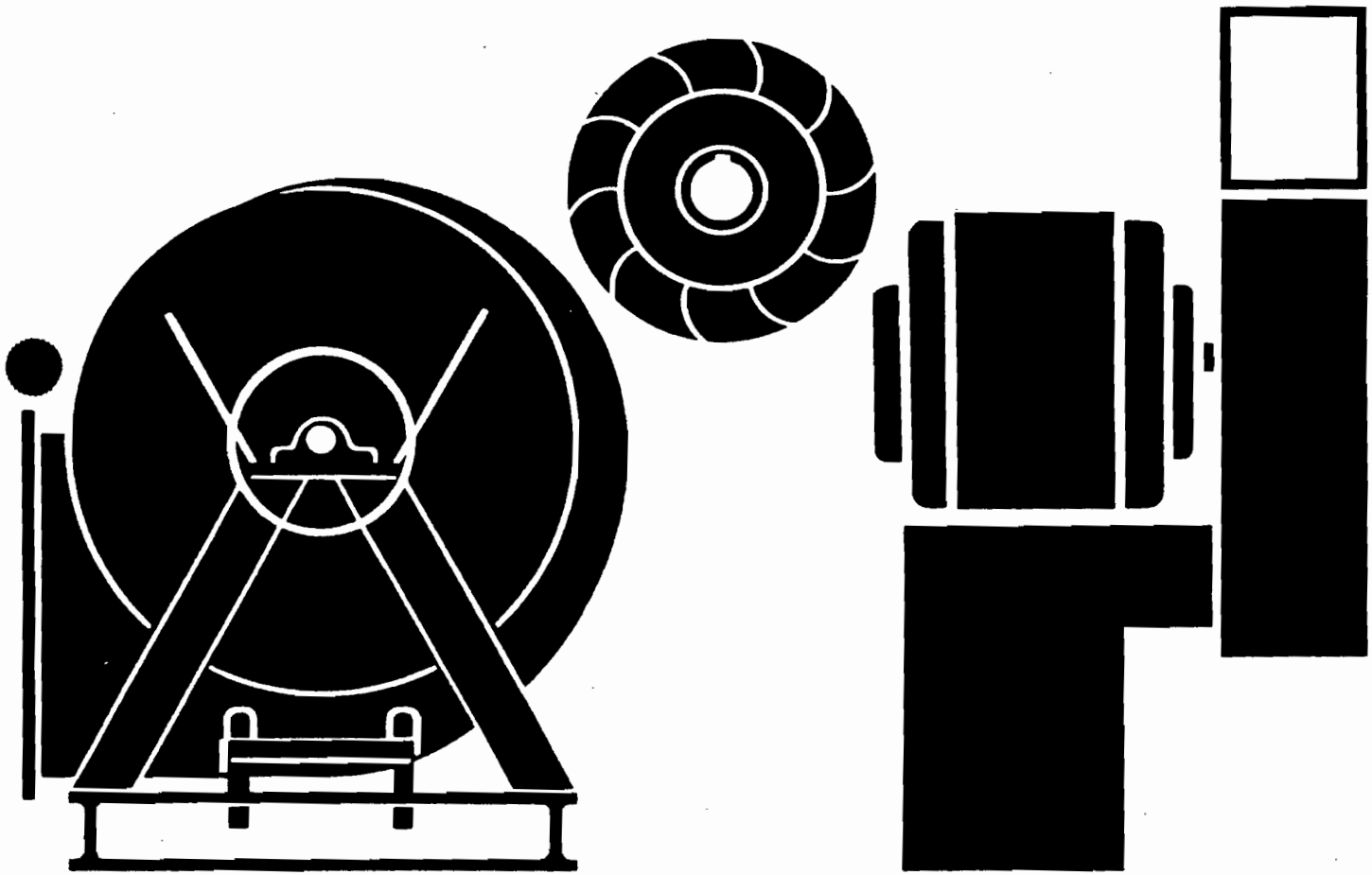
HORIZONTAL CROSS-FLOW

Model	CFM	Inlet & Outlet A x B In.	Length L Ft.	Width W In.	C In.	D In.	E In.	F In.	G In.	Sump Capacity Gal.	Rec. Liquid GPM	Overall Height In.	Ship* Wt. Lbs.	Operating Wt. Lbs.
HF-8	800	11x11	6	17	3/4	1	1	1 1/4	1	58	17	35	182	646
HF-12	1,200	14x14	6	20	3/4	1	1	1 1/4	1	69	21	38	224	781
HF-17	1,700	18x18	6	24	3/4	1	1	1 1/2	1 1/4	82	24	42	275	926
HF-21	2,100	21x21	6	27	3/4	1	1	1 1/2	1 1/4	92	28	45	316	1028
HF-25	2,500	24x24	6	30	3/4	1 1/2	1 1/2	1 1/2	1 1/4	102	32	48	357	1166
HF-31	3,100	27x27	6	33	3/4	1 1/2	1 1/2	1 1/2	1 1/4	113	35	51	419	1313
HF-37	3,700	30x30	6	36	3/4	1 1/2	1 1/2	1 1/2	1 1/4	125	39	54	481	1445
HF-45	4,500	33x33	6	39	3/4	1 1/2	1 1/2	1 1/2	1 1/4	134	42	57	563	1669
HF-50	5,000	36x36	6	42	3/4	1 1/2	1 1/2	1 1/2	1 1/4	144	45	5.0 ft.	615	1733
HF-67	6,700	36x36	6	48	1	2	2	1 1/2	1 1/4	165	51	5.5	690	1980
HF-85	8,500	42x42	6	54	1	2	2	2	1 1/2	186	56	6.0	824	2276
HF-105	10,500	48x48	6	60	1	2	2	2	1 1/2	206	60	6.5	1035	2639
HF-126	12,600	54x54	6	66	1	2	2	2	1 1/2	228	68	7.0	1242	2990
HF-150	15,000	60x60	6	72	1	2	2	2 1/2	2	247	74	7.5	1545	3460
HF-176	17,600	66x66	6	78	1	2	2	2 1/2	2	268	80	8.0	1751	3803
HF-190	19,000	66x72	6	84	1	2	2	2 1/2	2	290	86	8.0	1957	4151
HF-220	22,000	86x84	6	96	1	2	2	2 1/2	2	336	96	8.6	2466	4770
HF-245	24,500	66x96	6	105	1	2	2	3	3	371	112	9.0	2624	5325
HF-273	27,800	76x108	6	117	1	2	2	3	3	412	126	9.6	2826	5826
HF-300	30,000	86x108	6	126	1	2	2	3	3	453	138	10.0	3030	6330
HF-327	32,700	96x108	6	135	1	2	2	3	3	495	150	10.6	3180	7330

BEST AVAILABLE COPY

berglass Centrifugal Blowers

W. K. OUSLEY INC
P. O. DRAWER 750
650 AVE. B, S.W.
WINTER HAVEN FLA. 33880
813 - 324-4000



HARTZELL[®]

Hartzell Fan, Division of Castle Hills Corporation, Piqua, Ohio

Construction Features

A variety of corrosion problems plague industry today. Fans and blowers made of coated steel or metals such as stainless and monel can handle some problem areas. However, reinforced fiberglass and resin construction will meet even the most challenging demands.

Fiberglass centrifugal blowers can be used in most applications where corrosive elements exist in fume and vapor form at temperatures less than 200° F. The resistance to corrosive elements is a major advantage, but the physical properties of fiberglass equipment offer these additional advantages.

- Fiberglass equipment weighs 25% less than comparable equipment made of carbon steel.
- Fiberglass has an extremely high strength-to-weight ratio, stronger than steel on a per-pound basis.
- Dimensional stability of fiberglass is excellent. Fiberglass air moving equipment will not become brittle at low temperatures and at 0° F. the laminated fiberglass will be stronger than at room temperature.
- Fiberglass equipment offers a distinct advantage in price over stainless and monel (as much as 1/3 in original cost) and offers longer service life and requires less maintenance.

Hartzell fiberglass equipment is identical, except for part thickness, in design, overall specs and performance to our standard lines. The following are standard Hartzell fiberglass construction features:

- Special corrosive resistant polyester resin having a Class I flame spread rate of 25 or less.
- All structural parts in the airstream are fiberglass and resin. All taped joints inside the shell or body are three layers of two ounce material. All internal surfaces are protected with a 10 mil thickness of chemical resistant, flame retardant gel coat and all external surfaces have a heavy coating of resin applied before assembly.
- Internal hardware is 300 series stainless steel. Shafts are type 304; bolts and screws are type 316. Monel shafting and hardware are available as an extra-cost option for applications such as hydrochloric, hydrofluoric, or sulfuric acids, which attack stainless.

Where metal is subject to attack by the corrosive elements being handled, all metal parts can be resin-coated after assembly.

- A fiberglass and neoprene shaft seal is placed where the shaft leaves the housing along with a neoprene shaft siinger between the seal and wheel on belt drive units. (Seal is not gas tight.)
- All fiberglass radial and backward curved wheels are of multi-piece construction bonded together with resin and fiberglass material.

Maximum temperature limitation is 200° F. on all centrifugal blowers.

- All internal mounting hardware is encapsulated with a layer of fiberglass and resin.

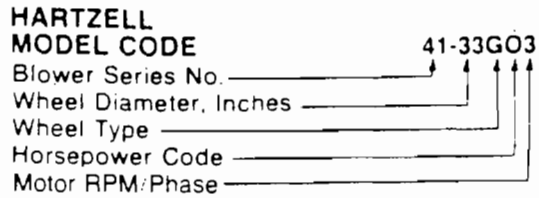
This bulletin lists Hartzell's complete line of fiberglass centrifugal blowers and accessories. More than 70 Hartzell offices can provide specific performance and installation data to meet your requirements. Call your nearest Hartzell representative for competent technical help.



Air Movement and Control Association Seal

Hartzell Propeller Fan Company certifies that the centrifugal blowers shown herein are licensed to bear the AMCA Seal. The ratings shown are based on tests made in accordance with AMCA Standard 210 and comply with the requirements of the AMCA Certified Ratings Program.

Selection Guide



3 Phase 1 Phase
 3 = 1750 C = 1750

How to use Hartzell Model Code

EXAMPLE:

Assume the required performance to be 16,276 CFM at 3" SP standard air. Reading across the 33" Rating Table, page 13, we find a blower RPM of 1306 and brake horsepower of 14.5. Motor horsepower required is 15; therefore, horsepower code is "O". Type specification would be "GO3". The complete blower specification would read: Series 41-33-GO3.

How To Use Capacity Tables

- (1) Select size, RPM and BHP for a given air delivery and pressure of a centrifugal blower from rating tables, pages 10 through 21. Performance ratings are based on standard air conditions, sea level 70°F. and 29.92 inches barometric pressure giving an air density of .075 lbs. per cubic foot. The specific gravity of air equals 1.00 at these conditions.
- (2) If non-standard temperature or altitude is involved, correct to standard air density (see Table 1).
- (3) For speeds above ratings consult factory.

Horsepower Code

Horsepower	1/4	1/3	1/2	3/4	1	1 1/2	2	3	5	7 1/2	10	15	20	25	30	40	50	60	75	100
Code Letter	D	E	F	G	H	I	J	K	L	M	N	O	P	Q	R	S	T	U	V	W

Altitude - Temperature Correction

Temperatures above or below 70° at sea level (0 ft.) are read vertically between the double lines, giving the proper correction factors. Altitudes above sea level at a constant 70°F. temperature are read horizontally between the double lines giving those factors. Any other factors are obtained by reading down to the desired temperature, then across to the desired altitude.

Example:

Assume the required performance to be 12,520 CFM at 6.15" SP, 175° F. and 2000 feet altitude.

1. Table 1 gives a factor of 1.30.

2. 6.15" SP × 1.30 = 8.0" SP for 70° F. at sea level.

3. A backward curved centrifugal blower, size 33", selected from the rating tables for the new condition shows 12,520 CFM at 8.0" SP, 1537 RPM and 23.9 BHP.

4. Correct the horsepower and static pressure in Item 3 to non-standard performance by dividing by the factor:
 8.0" SP ÷ 1.30 = 6.15 SP
 23.9 BHP ÷ 1.30 = 18.38 BHP

5. Final performance of this size 33" backward curved centrifugal blower at assumed conditions:
 12,520 CFM at 6.15" SP, 1537 RPM, 18.38 BHP, 175°F. and 2000 Ft.

Table 1 - Combined Altitude - Temperature Correction Factors

ALT. FT. / °F. TEMP.	0	1000	2000	3000	4000	5000	6000	7000	8000	9000	10000	11000	12000
-50	0.77	0.80	0.83	0.86	0.89	0.92	0.96	1.00	1.04	1.08	1.12	1.16	1.21
-25	0.82	0.85	0.89	0.92	0.95	0.98	1.03	1.07	1.11	1.15	1.20	1.24	1.29
0	0.87	0.90	0.94	0.97	1.01	1.04	1.09	1.13	1.17	1.22	1.27	1.31	1.37
25	0.91	0.95	0.98	1.02	1.06	1.09	1.14	1.18	1.23	1.27	1.33	1.37	1.43
50	0.96	1.00	1.04	1.08	1.11	1.15	1.20	1.25	1.30	1.34	1.40	1.45	1.51
70	1.00	1.04	1.08	1.12	1.16	1.20	1.25	1.30	1.35	1.40	1.46	1.51	1.57
100	1.06	1.10	1.14	1.19	1.23	1.27	1.33	1.38	1.43	1.48	1.55	1.60	1.66
125	1.10	1.14	1.19	1.23	1.28	1.32	1.38	1.43	1.49	1.54	1.61	1.66	1.73
150	1.15	1.20	1.24	1.29	1.33	1.38	1.44	1.50	1.55	1.61	1.68	1.74	1.81
175	1.20	1.25	1.30	1.34	1.39	1.44	1.50	1.56	1.62	1.68	1.75	1.81	1.88
200	1.25	1.30	1.35	1.40	1.45	1.50	1.56	1.63	1.69	1.75	1.83	1.89	1.96
250	1.34	1.39	1.45	1.50	1.55	1.61	1.68	1.74	1.81	1.88	1.96	2.02	2.10
300	1.43	1.49	1.54	1.60	1.66	1.72	1.79	1.86	1.93	2.00	2.09	2.16	2.25
350	1.53	1.59	1.65	1.71	1.77	1.84	1.91	1.99	2.07	2.14	2.23	2.31	2.40
400	1.62	1.69	1.75	1.82	1.89	1.96	2.04	2.12	2.20	2.27	2.35	2.45	2.55
450	1.72	1.79	1.86	1.93	2.00	2.08	2.16	2.24	2.33	2.41	2.50	2.60	2.70
500	1.81	1.88	1.96	2.03	2.11	2.19	2.28	2.36	2.46	2.54	2.62	2.74	2.85
550	1.91	1.98	2.06	2.14	2.22	2.30	2.40	2.49	2.58	2.68	2.77	2.89	3.00
600	2.00	2.08	2.16	2.24	2.33	2.42	2.50	2.61	2.71	2.80	2.90	3.03	3.14

NOTE: Above table has inverted values. Actual density is the reciprocal of the above values.

Abrasive/Erosive Atmospheres

HartKoate is an abrasive erosive resistant coating developed by Hartzell for application in environments where abrasive erosive conditions may exist. HartKoate helps prevent premature deterioration of equipment in environments where uncoated fans may fail.

Impact resistant HartKoate is applied to a 50-60 mil thickness suitable for temperatures to 200 F.

HartKoate is particularly appropriate for use when water mist and/or abrasive particles exist in the air stream.

Contact your Hartzell representative for further details concerning the application of HartKoate coating to fiberglass fans in corrosive atmospheres.

Installation Weights- Bearing/Shaft Sizes

Series 41

Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes			
15"	GH3	526	1 7/16"	40"	GI3	1885	2 7/16"	19"	FI3	372	1 7/16"	30"	FL3	626	1 5/16"			
	GI3	526	1 7/16"		GJ3	1885	2 7/16"		FJ3	372	1 7/16"		FM3	629	1 5/16"			
	GJ3	529	1 7/16"		GK3	1912	2 7/16"		FK3	399	1 7/16"		FN3	649	1 5/16"			
	GK3	529	1 7/16"		GL3	1932	2 7/16"		FL3	444	1 7/16"		FO3	709	1 5/16"			
	GL3	549	1 7/16"		GM3	1972	2 7/16"		FM3	447	1 7/16"		FP3	739	1 5/16"			
	GM3	554	1 7/16"		GN3	1987	2 7/16"		FN3	466	1 7/16"		FQ3	779	1 5/16"			
22"	GH3	772	1 11/16"	49"	GO3	2047	2 7/16"	23"	FO3	517	1 7/16"	33"	FR3	869	1 5/16"			
	GI3	772	1 11/16"		GP3	2077	2 7/16"		FP3	547	1 7/16"		FS3	909	1 5/16"			
	GJ3	776	1 11/16"		GQ3	2127	2 7/16"		FQ3	587	1 7/16"		FT3	1004	1 5/16"			
	GK3	776	1 11/16"		GR3	2177	2 7/16"		FR3	667	1 7/16"		*FU3	529	1 5/16"			
	GL3	806	1 11/16"		GS3	2277	2 7/16"		26"	FJ3	404		1 11/16"	Series 42	FL3	692	1 5/16"	
	GM3	813	1 11/16"		GT3	2327	2 7/16"			FK3	431		1 11/16"		FM3	695	1 5/16"	
	GN3	854	1 11/16"		Series 43	GL3	2415			2 5/16"	FL3		451		1 11/16"	FN3	705	1 5/16"
	GO3	865	1 11/16"			GM3	2465			2 5/16"	FM3		496		1 11/16"	FO3	775	1 5/16"
GP3	926	1 11/16"	GN3	2483		2 5/16"	FN3	516		1 11/16"	FP3	805	1 5/16"					
27"	GI3	954	1 15/16"	GO3		2558	2 5/16"	FO3		535	1 11/16"	FQ3	855		1 5/16"			
	GJ3	959	1 15/16"	GP3		2596	2 5/16"	FP3		565	1 11/16"	FR3	945		1 5/16"			
	GK3	959	1 15/16"	GQ3		2658	2 5/16"	FQ3		605	1 11/16"	FS3	985		1 5/16"			
	GL3	996	1 15/16"	GR3		2721	2 5/16"	FR3	695	1 11/16"	FT3	1075	1 5/16"					
	GM3	1004	1 15/16"	GS3		2846	2 5/16"	FS3	735	1 11/16"	*FU3	600	1 5/16"					
	GN3	1054	1 15/16"	GT3	2908	2 5/16"	Series 42	FK3	489	1 11/16"	*FV3	600	1 5/16"					
	GO3	1069	1 15/16"	GU3	2958	2 5/16"		FL3	509	1 11/16"	*FW3	600	1 5/16"					
	GP3	1144	1 15/16"	GV3	3063	2 5/16"		FM3	555	1 11/16"	10"	FC3	63					
GQ3	1164	1 15/16"	GW3	3123	2 5/16"	FN3		574	1 11/16"	12"	FF3	78						
GR3	1190	1 15/16"	Series 43			FO3		625	1 11/16"	14"	FG3	96						
33"	GI3	1355				2 3/16"		16"	FH3	302	1 3/16"	Series 42						
	GJ3	1355				2 3/16"		FI3	302	1 3/16"								
	GK3	1382				2 3/16"		FJ3	302	1 3/16"								
	GL3	1397				2 3/16"	FK3	338	1 3/16"									
	GM3	1454				2 3/16"	FL3	358	1 3/16"									
	GN3	1482				2 3/16"	FM3	361	1 3/16"									
	GO3	1514				2 3/16"	FN3	380	1 3/16"									
	GP3	1544	2 3/16"	FO3	431	1 3/16"												
GQ3	1594	2 3/16"	FP3	460	1 3/16"													
GR3	1644	2 3/16"	Series 43			FT3	940	1 11/16"										

*Net installation weights are for Arrangement 1. (Less motor & drive.)

Metric Conversion Table

FROM	TO	MULTIPLY BY
Inches (in.)	Millimeter (mm)	25.400
Feet (ft.)	Meter (m)	0.3048
Velocity (ft./min.)	Meter/Second (m/s)	0.00508
Volume Flow (cfm)	Cubic Meter/Second (m ³ /s)	0.00047195
Pressure (in. w.g.)	Pascal (N/m ²)	248.36
Density (lb/ft ³)	Kilogram/Cubic Meter (Kg/m ³)	16.018
Power (hp)	Watt (w)	745.70
Square Foot (ft ²)	Square Meter (m ²)	0.09290
Square Inch (in. ²)	Square Meter (m ²)	0.0006451

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Series 41

Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes		
15"	GH3	526	1 7/16"	40"	GI3	1885	2 7/16"	19"	FI3	372	1 7/16"	30"	FL3	626	1 15/16"		
	GI3	526	1 7/16"		GJ3	1885	2 7/16"		FJ3	372	1 7/16"		FM3	629	1 15/16"		
	GJ3	529	1 7/16"		GK3	1912	2 7/16"		FK3	399	1 7/16"		FN3	649	1 15/16"		
	GK3	529	1 7/16"		GL3	1932	2 7/16"		FL3	444	1 7/16"		FO3	709	1 15/16"		
	GL3	549	1 7/16"		GM3	1972	2 7/16"		FM3	447	1 7/16"		FP3	739	1 15/16"		
	GM3	554	1 7/16"		GN3	1987	2 7/16"		FN3	466	1 7/16"		FQ3	779	1 15/16"		
22"	GH3	772	1 11/16"	49"	GO3	2047	2 7/16"	23"	FO3	517	1 7/16"	33"	FR3	869	1 15/16"		
	GI3	772	1 11/16"		GP3	2077	2 7/16"		FP3	547	1 7/16"		FS3	909	1 15/16"		
	GJ3	776	1 11/16"		GQ3	2127	2 7/16"		FQ3	587	1 7/16"		FT3	1004	1 15/16"		
	GK3	776	1 11/16"		GR3	2177	2 7/16"		FR3	667	1 7/16"		*FU3	529	1 15/16"		
	GL3	806	1 11/16"		GS3	2277	2 7/16"		26"	FJ3	404		1 11/16"	FL3	692	1 15/16"	
	GM3	813	1 11/16"		GT3	2327	2 7/16"			FK3	431		1 11/16"	FM3	695	1 15/16"	
	GN3	854	1 11/16"		Series 43	GL3	2415			2 5/16"	FL3		451	1 11/16"	FN3	705	1 15/16"
	GO3	865	1 11/16"			GM3	2465			2 5/16"	FM3		496	1 11/16"	FO3	775	1 15/16"
GP3	926	1 11/16"	GN3	2483		2 5/16"	FN3	516		1 11/16"	FP3	805	1 15/16"				
27"	GI3	954	1 15/16"	GO3		2558	2 5/16"	FO3		535	1 11/16"	FQ3	855	1 15/16"			
	GJ3	959	1 15/16"	GP3		2596	2 5/16"	FP3		565	1 11/16"	FR3	945	1 15/16"			
	GK3	959	1 15/16"	GQ3		2658	2 5/16"	FQ3		605	1 11/16"	FS3	985	1 15/16"			
	GL3	996	1 15/16"	GR3		2721	2 5/16"	FR3	695	1 11/16"	FT3	1075	1 15/16"				
	GM3	1004	1 15/16"	GS3		2846	2 5/16"	FS3	735	1 11/16"	*FU3	600	1 15/16"				
	GN3	1054	1 15/16"	GT3	2908	2 5/16"	Series 42	FK3	489	1 11/16"	10"	FC3	63				
	GO3	1069	1 15/16"	GU3	2958	2 5/16"		FL3	509	1 11/16"	12"	FF3	78				
	GP3	1144	1 15/16"	GV3	3063	2 5/16"		FM3	555	1 11/16"	14"	FG3	96				
GQ3	1164	1 15/16"	GW3	3123	2 5/16"	FN3		574	1 11/16"								
GR3	1190	1 15/16"				FO3		625	1 11/16"								
33"	GI3	1355	2 3/16"	16"	FH3	302		1 3/16"	FP3	655	1 11/16"						
	GJ3	1355	2 3/16"		FI3	302		1 3/16"	FQ3	715	1 11/16"						
	GK3	1382	2 3/16"		FJ3	302		1 3/16"	FR3	805	1 11/16"						
	GL3	1397	2 3/16"		FK3	338	1 3/16"	FS3	845	1 11/16"							
	GM3	1454	2 3/16"		FL3	358	1 3/16"	FT3	940	1 11/16"							
	GN3	1482	2 3/16"		FM3	361	1 3/16"										
	GO3	1514	2 3/16"		FN3	380	1 3/16"										
	GP3	1544	2 3/16"		FO3	431	1 3/16"										
	GQ3	1594	2 3/16"		FP3	460	1 3/16"										
	GR3	1644	2 3/16"														

*Net installation weights are for Arrangement 1. (Less motor & drive.)

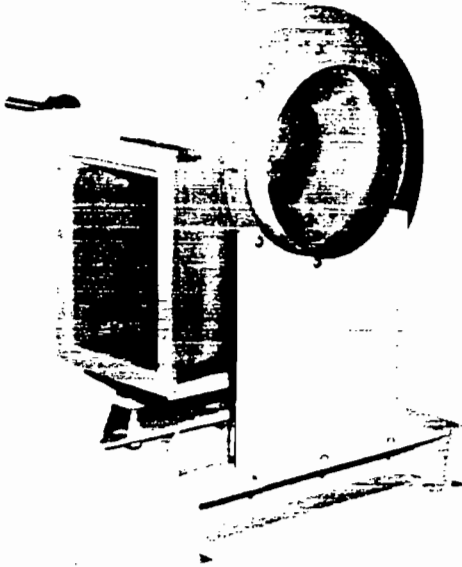
Metric Conversion Table

FROM	TO	MULTIPLY BY
Inches (in.)	Millimeter (mm)	25.400
Feet (ft.)	Meter (m)	0.3048
Velocity (ft./min)	Meter/Second (m/s)	0.00508
Volume Flow (cfm)	Cubic Meter/Second (m ³ ·s)	0.00047195
Pressure (in. w.g.)	Pascal (N/m ²)	248.36
Density (lb./ft ³)	Kilogram/Cubic Meter (Kg/m ³)	16.018
Power (hp)	Watt (w)	745.70
Square Foot (ft ²)	Square Meter (m ²)	0.09290
Square Inch (in ²)	Square Meter (m ²)	0.0006451

Backward Curved Blower (Belt Drive)

Blowers available in SWSI only

The belt drive airfoil backward curved centrifugal blower offers non-overloading efficiency and economy in corrosive atmospheres at static pressures up to 12". The wheel and housing are constructed with a special corrosive resistant polyester resin having a Class I flame spread rate of 25 or less. No metal parts are exposed in the airstream. All internal hardware is 300 series stainless steel encapsulated with fiberglass.



Arrangement #10 Shown.



Series 41



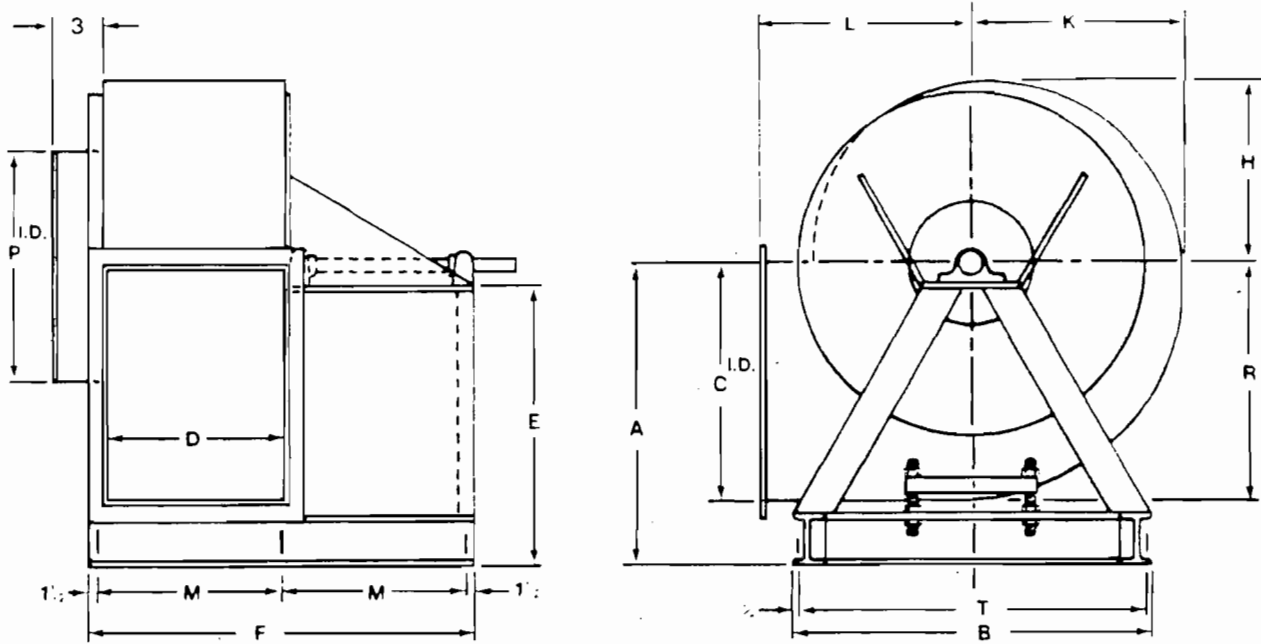
Features

- **Sizes** — 15", 22", 27", 33", 40", 49" wheel diameters.
- **Arrangements** — available in Arrangements #1, #9 or #10.
- **Rotation** — clockwise and counter clockwise rotation. Rotatable in field.
- **Discharges** — available discharges shown on page 9.
- **Packaged unit** — motor and drive mounted by factory.
- **Easy installation and maintenance** — motor, drive and bearings are readily accessible for ease in wiring, installation, adjustment and lubrication.
- **Wheel** — a true airfoil type of multi-piece, solid fiberglass construction bonded together with resin and fiberglass material. Airfoil backwardly inclined blades offer greater versatility for industrial applications. Wheel has non-overloading horsepower characteristics in that brake horsepower levels off at a point that prevents motor overload if system changes occur. Wheel Type G.
- **Motors** — open end drip proof are standard. Totally enclosed fan cooled and other special motors are available upon request.
- **Variable pitch drives** are standard on all units up to 10 HP.
- **Flanged outlets are standard.** Inlet flanges are optional. Drilling of flanges is optional. (Position of drilled holes must be specified by customer.)
- **All units are test run and electronically balanced** before shipment.
- **Heavy Duty Design** suitable for service up to and including Class III.
- **Bearings** — heavy duty, self-aligning, double row spherical roller type pillow block bearings are standard and are furnished with extended lubrication lines. Bearings have floating labyrinth seals. (See page 7 for Bearing/Shaft sizes.)
- **Shafts** are 304 stainless steel as standard. None! available at extra cost.
- **Bases** — heavy gauge hot rolled steel, epoxy coated.
- **Maximum Temperature:** 200° F.
- **Maximum tip speed:** 16,000 FPM
- **Accessories** —
See pages 22 and 23.

Principal Dimensions

Size	Wheel Dia.	A	B	C	D	E	F	H	K	L	M	P	R	T	Max. Motor Frame Size	
															ODP	TEFC
15	15 1/2	32 1/2	33	16	11 1/2	30 1/2	41	12 1/2	14 1/2	16 1/2	19	16	16 1/2	31 1/2	326T	286T
22	22	32	33	23	17 1/2	30 1/2	46	18	21 1/2	21 1/2	21	23	23 1/2	31 1/2	326T	286T
27	27 1/2	38 1/2	43	29	21	35 1/2	51	22 1/2	26 1/2	24	24	26	29	41 1/2	326T	286T
33	33 1/2	43 1/2	50	35 1/2	25 1/2	40 1/2	56	27 1/2	31 1/2	29 1/2	28	34	35 1/2	48 1/2	326T	286T
40	41 1/2	51 1/2	59	43 1/2	31 1/2	48 1/2	62	33 1/2	38 1/2	35 1/2	29	41	43 1/2	57 1/2	326T	286T
49	50	61 1/2	73	52 1/2	38 1/2	58	92	41	47 1/2	40	44	50	53 1/2	71 1/2	447T	447T

NOTES: ON 15 AND 22 SIZES WITH 254T FR. AND LARGER MOTORS, BASE DIMENSIONS MUST BE CERTIFIED BY THE FACTORY. DIMENSIONS AND SPECIFICATIONS ARE SUBJECT TO CHANGE. CERTIFIED PRINTS ARE AVAILABLE.

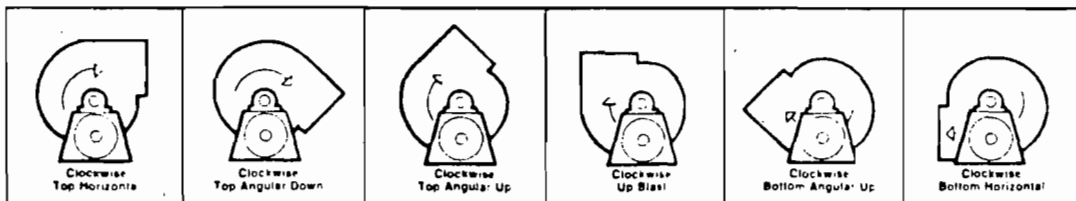


Material Specifications — Inches

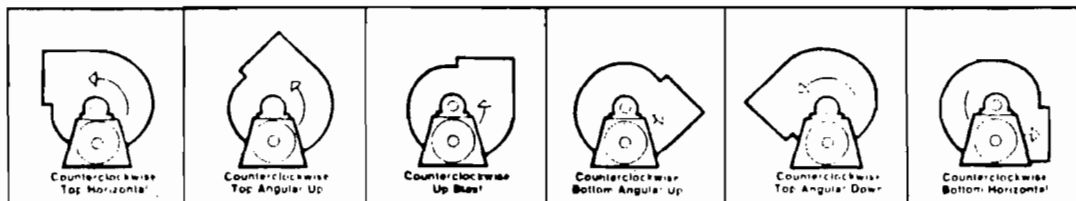
Size	HOUSING (Thickness)				(H.R.S.) FAN STAND			WHEEL (Thickness)		
	Scroll	Inlet Cone	Flanges		Back Plate	H-Beam	Channel	Blade	Back Plate	Outer Panel
			Inlet	Outlet						
15	5/16	5/16	3/16	5/16	1/2	6 x 4	4	3/4	1/2	1/2
22	5/16	7/16	1/2	5/16	1/2	6 x 4	4	3/4	5/8	5/8
27	1/2	1/2	5/16	1/2	1/2	6 x 4	4	3/4	3/4	3/4
33	1/2	5/8	3/8	1/2	1/2	6 x 4	4	3/4	7/8	7/8
40	5/8	3/4	7/16	5/8	1/2	6 x 4	4	3/4	1	1
49	5/8	15/16	7/16	1/2	1/2	6 x 4	4	1	1 1/8	1 3/8

Blower Discharges

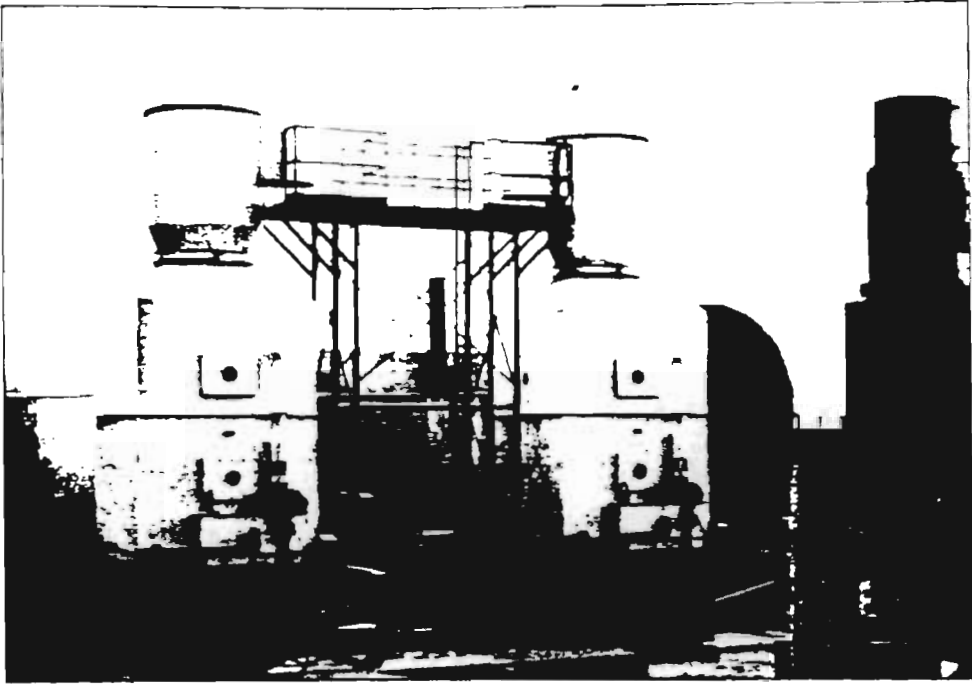
Clockwise



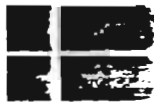
Counterclockwise



FIBERGLASS REINFORCED PLASTIC



INDUSTRIAL VENTILATION EQUIPMENT



BEVERLY PACIFIC CORPORATION

Beverly Pacific Corporation

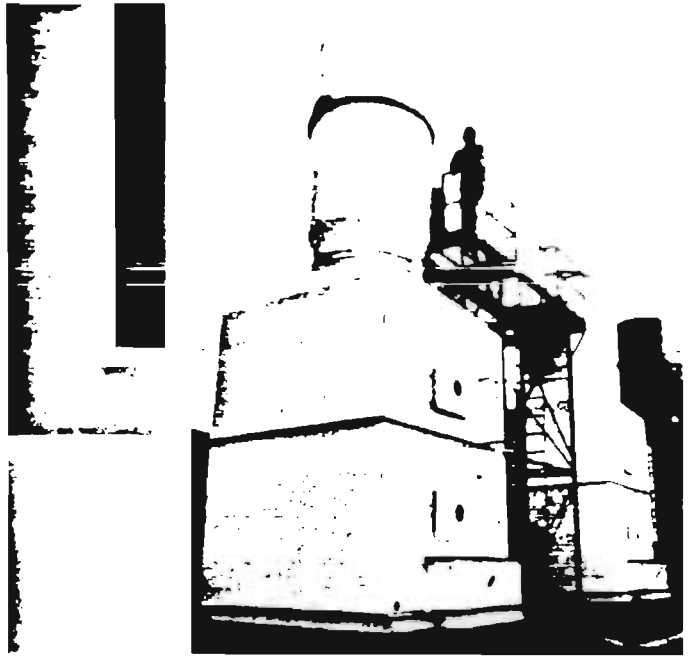
... a "qualified fabricator" ...

... an "important function"

There are many factors involved in order to determine whether a company is a "qualified FRP fabricator". The main factors a person with purchasing responsibilities needs to recognize are the specific factors with which Beverly Pacific Corporation has had years of experience.

These factors deal with the handling and managing of the construction process itself — a few, of which, are as follows:

1. A "qualified fabricator" should be able to exhibit expertise in the basic principles of building corrosion-resistant laminates.
2. A "qualified fabricator" should have personnel familiar with resin compounding and curing, including variables such as catalysts, promoters, resin, reinforcement, time, temperature, humidity, rate of exotherm, mass of structure, etc.
3. A "qualified fabricator" should be able to demonstrate that shop personnel have necessary understanding and ability to produce good quality laminates consistently.
4. A "qualified fabricator" should apply proven procedures to assure adequate quality control of raw material and finished products.
5. A "qualified fabricator" should be able to use and produce engineering specifications, drawings and equipment designs and fabricate in accordance therewith.



BEVERLY PACIFIC CORPORATION ...

... a "qualified fabricator"

Beverly Pacific Corporation has served industry for over a quarter century. Our products, service, component equipment and complete engineered systems are located throughout the nation and around the world.

We have a "HIGHLY QUALIFIED TEAM" of engineers, production supervisors and experienced plant personnel, equipped with the latest production equipment, tools and proven methods of fabrication. This combination offers economical, dependable and efficient "ANSWERS" to your exhaust ventilation and corrosion control "PROBLEMS", and we want to serve you.



... a "necessity"

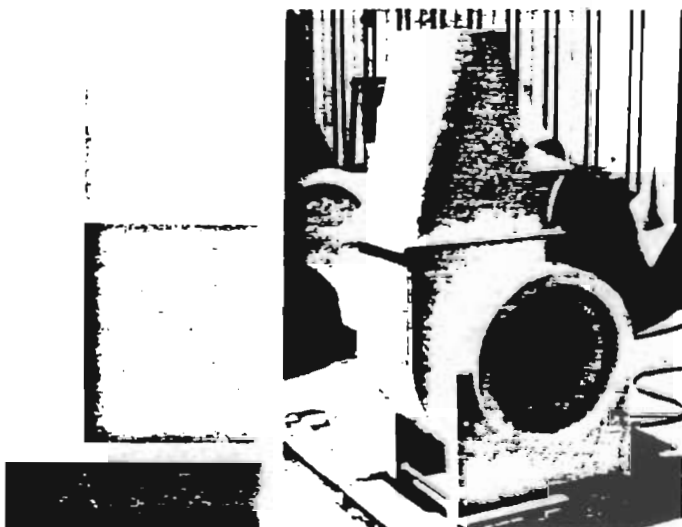
The "chemical resistance" of a *Fiberglass Reinforced Plastic (FRP)* product depends on the resin system and the method and type of reinforcement used in the construction. Polyester resin systems provide the best overall chemical resistance to the widest possible range of chemical environments. Superior performance of the resin is then assured by combining it with fiberglass and/or synthetic surfacing materials designed to accomplish both the "chemical resistance" and the "structural" requirements of the product.



POLYESTER RESIN SYSTEMS...

... the "answer"

The continuing combined technical efforts of manufacturers such as *Beverly Pacific* and the producers of polyester resin have resulted in three (3) general **CHEMICAL-RESISTANT** polyester resin system groups: *Isophthalic, Bisphenol and Vinyl Ester* polyesters. Each of these polyester resin systems are available in **FIRE-RETARDANT** grades.

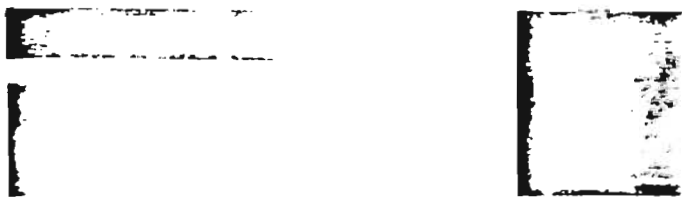


PRODUCTION CAPABILITIES...

... the "dependable"

Beverly Pacific specializes in "**CORROSION CONTROL THRU ENGINEERING**", utilizing the unexcelled characteristics of *Fiberglass Reinforced Plastic (FRP)* materials in the design, fabrication and installation of industrial exhaust systems, component equipment and services requiring a high degree of corrosion resistance and exhaust emission contaminate removal.

The fabrication of standard or custom designed hoods, ducts, fittings, exhaust fans, fume scrubbers and washers, and exhaust stacks is one of the many services we offer to the metal plating, anodizing, chem-milling, petro-chemical and chemical processing industries.



1.0 SCOPE OF SPECIFICATIONS

1.1 This specification describes the materials of construction, procedures and physical properties that Beverly Pacific employs in the fabrication of Fiberglass Reinforced Plastic (FRP) equipment, utilizing hand lay-up and spray-up methods of construction, in compliance with the N.B.S. Voluntary Product Standard PS 15-69 for "Custom Contact-Molded Reinforced Polyester Chemical Resistant Process Equipment" issued by the U.S. Department of Commerce.

1.2 This standard is not intended to cover the selection of the exact resin of fiberglass reinforcement combination for any specific application. The specific resin selection is to be accomplished with the aid of the resin manufacturers' corrosion charts and/or recommendations made by their technical service departments.

2.0 GENERAL LAMINATE CONSTRUCTION

2.1 The FRP laminate shall consist of an inner surface, an interior layer, a structural layer and an exterior surface layer.

2.2 The compositions specified for the inner surface and the interior layer are intended to achieve optimum chemical resistance. This portion of the laminate is referred to as the "corrosion barrier".

2.3 The use of a premium grade chemical resistant resin throughout the laminate, or the use of a premium grade resin for the "corrosion barrier" in combination with an isophthalic resin for the structural layer, shall be agreed upon with the purchaser. This agreement shall be as specified on the request for quotation, our proposal, your acknowledgement and/or the drawings submitted for approval.



2.4 The laminate surface shall have a Barcol hardness of at least 90 percent of the resin manufacturers' minimum specification.

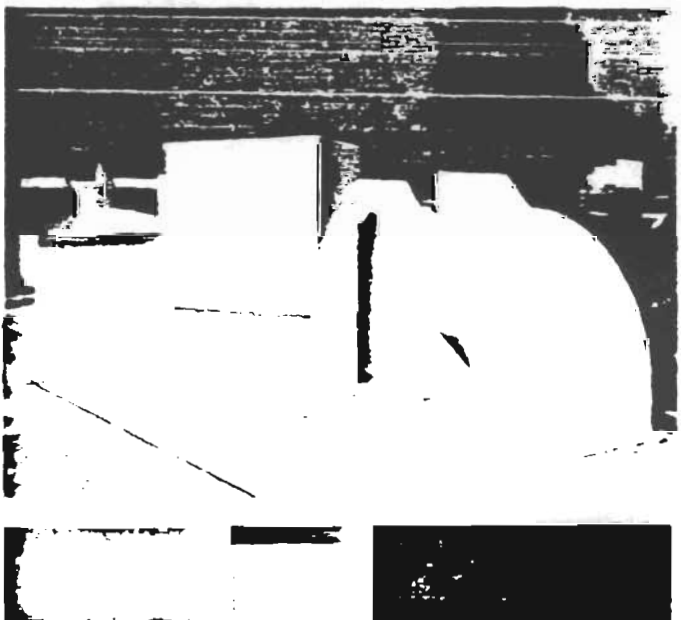
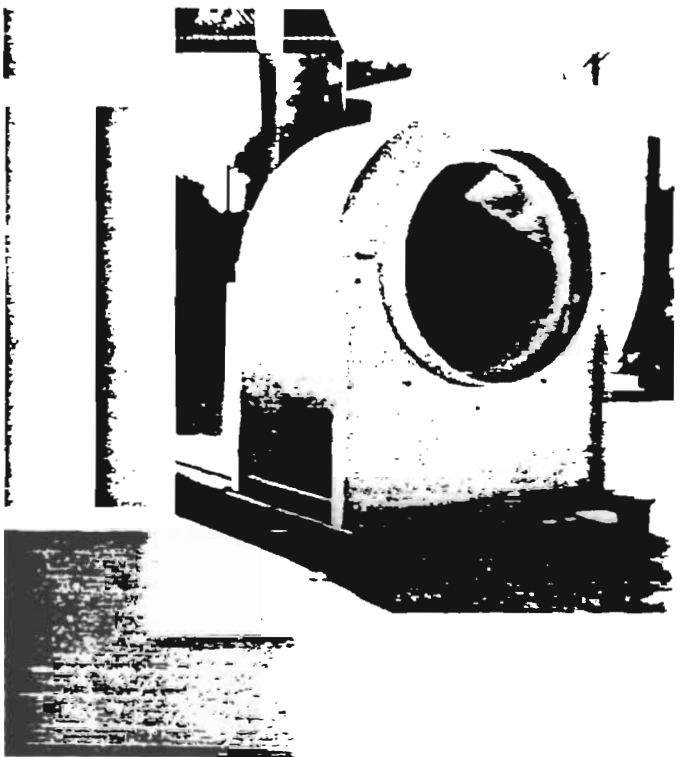
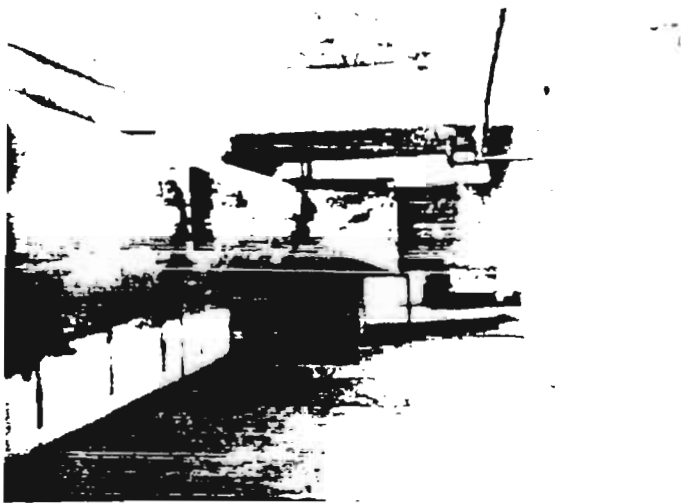
3.0 HAND LAY-UP AND SPRAY-UP LAMINATE CONSTRUCTION

3.1 **INNER SURFACE:** The inner surface resin shall be between 0.010 and 0.020 inches thick and be reinforced with glass or synthetic surfacing veil, depending on the chemical environment. This surface shall be free of cracks and crazing, having an average of not more than two (2) pits per square foot, providing these pits are less than 1/8" in diameter and not more than 1/32" deep. All pits must be covered with sufficient resin to prevent exposure of inner surface reinforcement.

3.2 **INTERIOR LAYER:** A minimum of 0.100 inch of laminate next to the inner surface shall be reinforced with not less than twenty (20) percent nor more than thirty (30) percent by weight of noncontinuous glass (chopped strand) fibers, having fiber lengths of 0.5 to 2.0 inches.

3.3 **STRUCTURAL LAYER:** The structural layer of the laminate shall provide the additional strength necessary to meet the tensile and flexural requirements. Where separate layers such as mat or woven roving are used, all layers shall be lapped a minimum of one (1) inch. Laps shall be staggered as much as possible and if woven roving is used, alternate layers of chopped strand glass shall be used.

3.4 **EXTERIOR LAYER:** The exterior surface shall be relatively smooth with no exposed fibers or sharp projections. Hand-work finish is acceptable; however, a sufficient amount of resin shall be present to prevent fiber exposure. The final laminate shall be coated with a resin containing a paraffin surfacing agent to achieve a fully cured exterior surface.



4.0 MATERIALS OF CONSTRUCTION

4.1 **RESIN:** The resin used shall be of commercial grade and shall have had previous service history acceptable for the specific environment. Environment includes the nature of the chemical, the concentration and the service temperature.

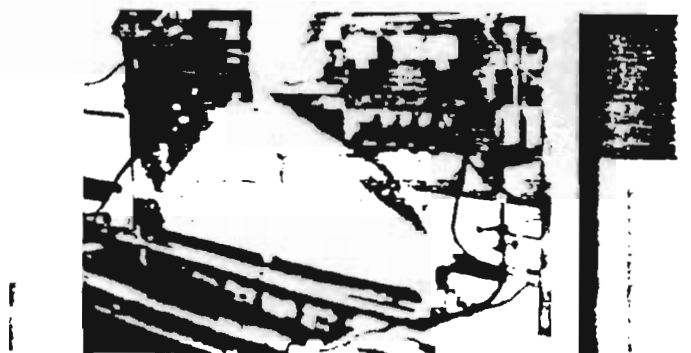
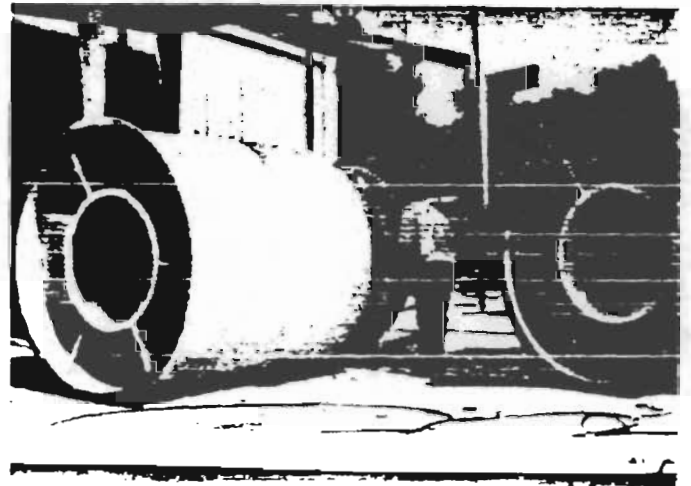
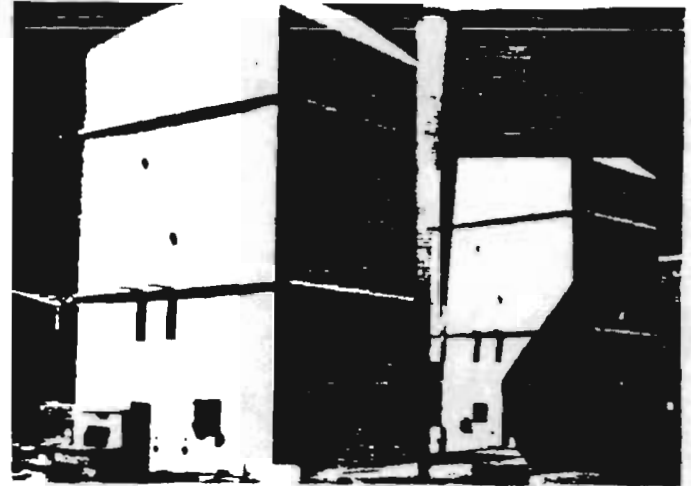
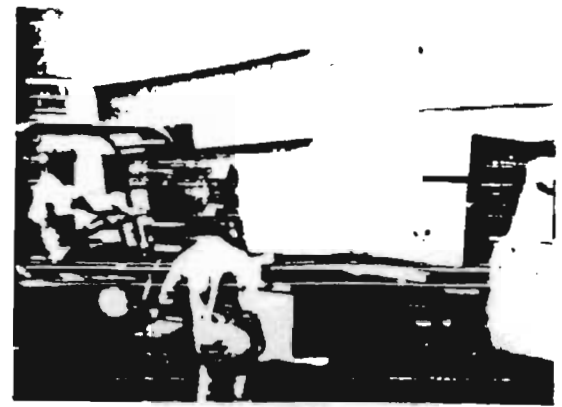
4.2 **FILLERS AND PIGMENTS:** The resins used shall not contain fillers or pigments except when required as follows:

- a. Up to 5% thixotropic agent which will not interfere with visual inspection may be added for viscosity control.
- b. Antimony compounds or other fire-retardant agents may be added to improve fire resistance at the request of the purchaser.
- c. Ultraviolet absorbers and/or pigments shall be added to final resin coating on the exterior surface to improve weather resistance.
- d. To insure a tack-free, fully cured, corrosion-resistant surface, up to 0.6 percent of paraffin wax, by weight, must be added to the final resin coat.

4.3 **SURFACE REINFORCEMENT:** The glass fiber reinforcement used on surfaces exposed to chemical environment shall be Type "C" monofilament surfacing veil, having a thickness of 10 to 20 mils, a silane finish and a styrene soluble binder.

4.4 **OPTIONAL SURFACE REINFORCEMENT:** Where the chemical environment would attack glass fibers, synthetic surfacing materials such as acrylic, polyester, asbestos or other organic fiber may be used, as agreed upon by Beverly Pacific and the purchaser.

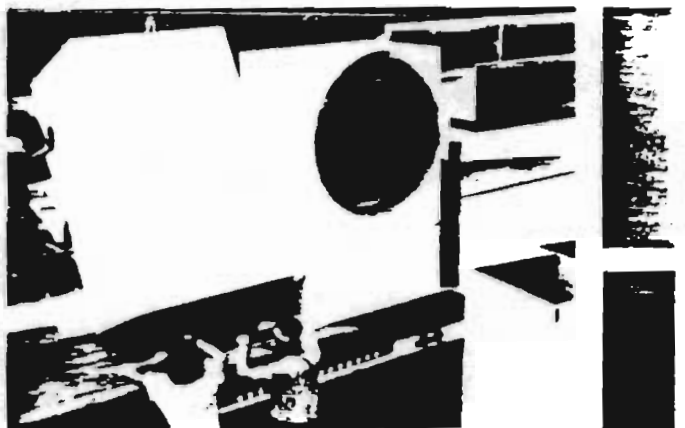
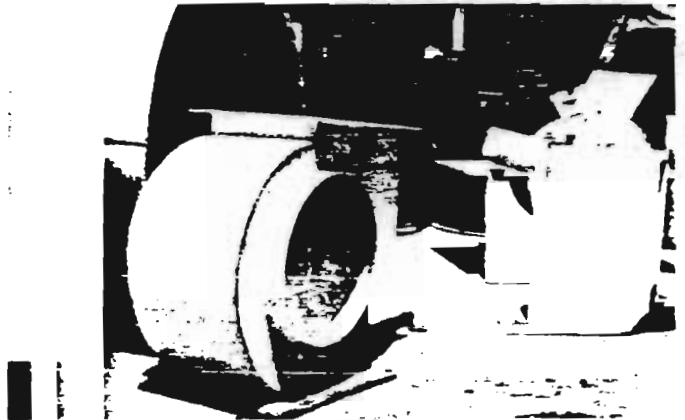
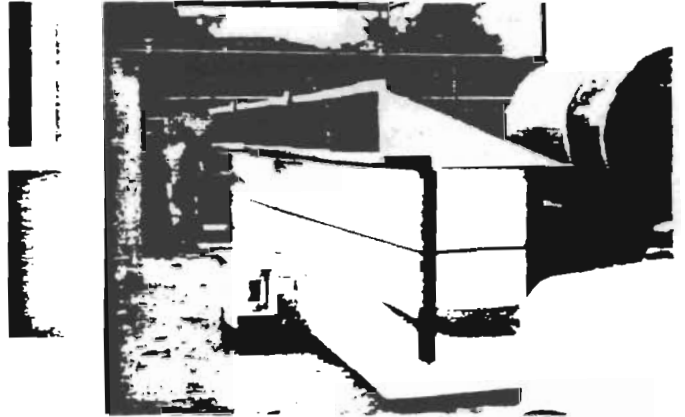
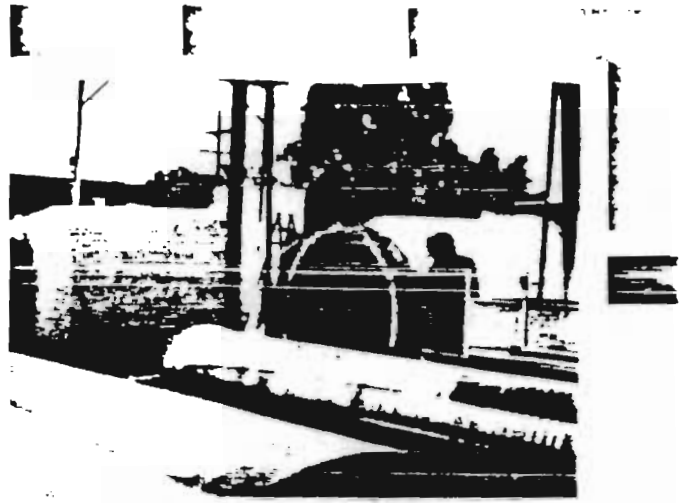
4.5 **CHOPPED STRAND MAT REINFORCEMENT:** Chopped strand glass mat used for reinforcement shall be Type "E" glass, 1½ oz. per square foot, having a silane finish and a soluble binder.



WOVEN ROVING REINFORCEMENT:
Woven roving used for additional structural reinforcement shall be 60 end, Type "F" glass, having a silane finish

GUN ROVING REINFORCEMENT:
Continuous gun roving used in chopper gun spray-up shall be 60 end, Type "E" glass having a silane or chrome-silane finish

Note: As stated in Paragraph 1.1 of these specifications, Beverly Pacific's standard methods of construction comply with PS15-69; however, as evidence of our industry leadership, up-graded modifications of this quality standard have been utilized by Beverly Pacific for years. At the time of this printing, it is our understanding that such up-graded modifications are to be standardized by proposed ASTM Product Standards for the corrosion-resistant equipment manufacturing industry.



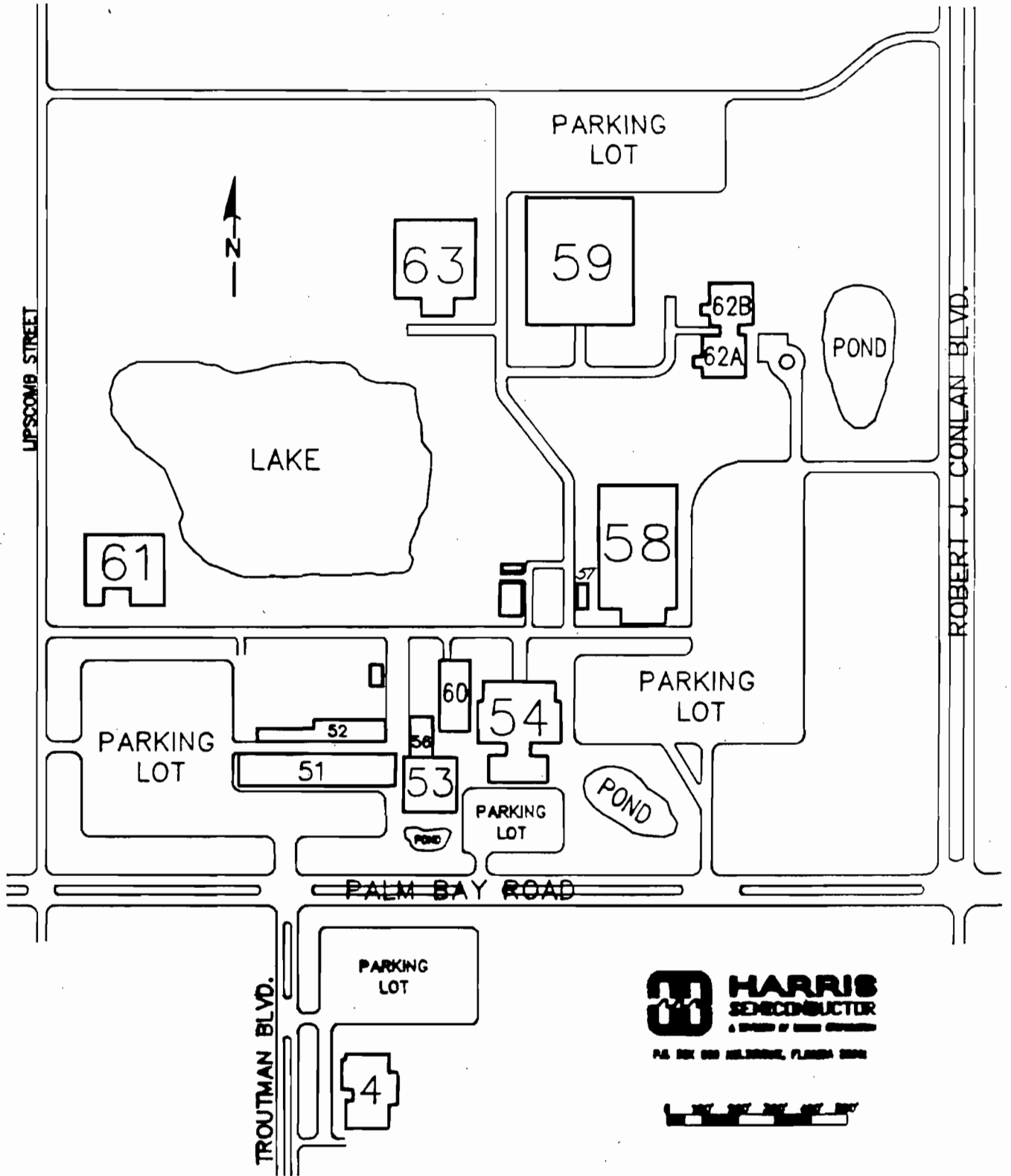
HARRIS SEMICONDUCTOR

B-54 Air Permit

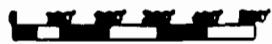
Consolidation

ATTACHMENT E

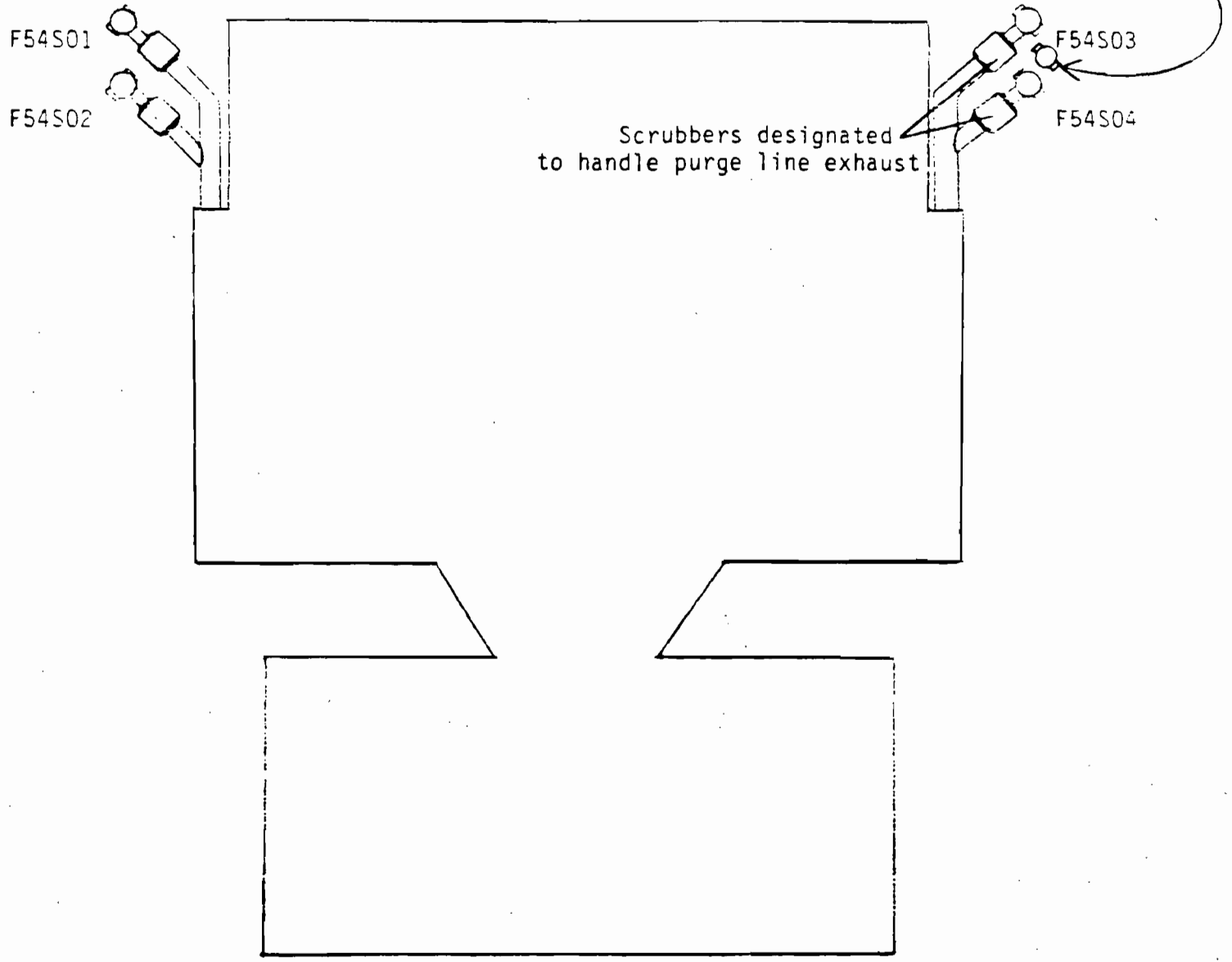
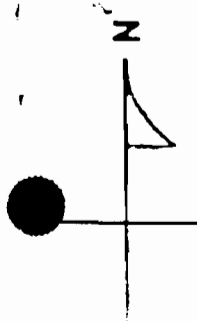
Maps









HARRIS
 SEMICONDUCTOR
 A DIVISION OF TEXAS INSTRUMENTS
 P.O. BOX 600 MELBOURNE, FLORIDA 32902



HARRIS SEMICONDUCTOR
SCRUBBER LOCATIONS
BUILDING 54



LEGEND

-  - Horizontal Scrubber
-  - Vertical Scrubber
-  - Exhaust Stack
-  - Exhaust Fan
-  - Stack mounted on fan
-  - Epitaxial Scrubber

RECEIVED

FS-JRK-139-88

MAR 3 1988

March 2, 1988

DER-BAQM

Mr. C. H. Fancy
Deputy Bureau Chief
Department of Environmental Regulation
Bureau of Air Quality Management
2600 Blair Stone Road
Tallahassee, Florida 32301

Reference: HARRIS SEMICONDUCTOR
B-54 Consolidated Air Permit

Dear Mr. Fancy:

On February 17, 1988, representatives from Harris and the Florida DER met in Orlando to discuss the status of air permits at Harris Semiconductor's facility in Palm Bay. At that meeting it was agreed that Harris would submit modified air permits. The purpose of the permit modifications was as follows:

1. Consolidate permits on a by building basis to reduce the existing number of permits.
2. To accurately quantify the current air emissions.

Enclosed is the modified permit application for Semiconductor's Building 54.

If you should have any questions about the enclosed information, please feel free to contact me at (305) 724-7467.

Sincerely,



J. R. Kolanek, Manager
Environmental Services

/pgc

cc: A. T. Sawicki
L. R. Hutker
D. R. Erdley
R. R. Sands

Purolator courier.

Purolator Account No. to be billed: 53-94-2777 Date: 3-2-88

683933792

Service - Check One - See reverse side for detail

ParaLetter Overnight Letter ParaPak Overnight Pack Priority National Overnight Service Nationwide Priority Regional Overnight Service

Standard 2-day Service Optional Service Saturday Delay Extra Charge Hold for Pick-up

Payment: Sender Prepaid Third Party Cash Check Collect

From: Sender's Name L.R. KLANEK Sender's Area Code/Phone Number (305) 724-7576

To: Recipient's Name C.H. FANCY Recipient's Area Code/Phone Number (904) 4880190

Company Name HARRIS SEMICONDUCTOR

Company Name FLORIDA DER Dept./Suite

Street Address BLDG PALM BAY ROAD

Street Address (P.O. Box numbers not deliverable) 2600 BLAIR STONE RD

City PALM BAY State FL Zip Code - Required 3279105

City TALLAHASSEE State FL Zip Code - Required 32301

Sender's Signature [Signature] P.O. or Reference Number

Third Party Billing Name/Address 1/6 58-55

Tariff Rate Item SM Origin Airport MCP Destination Airport

Weight L W H 1

Advance Valuation Code Amount Code Amount Total Charge

2-0710

Special Charge 06 Route Courier Guard Initial S.S. - Last 4 digits **PUROLATOR USE ONLY**

BL-2 Rev. 4-86

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DEPARTMENT OF ENVIRONMENTAL REGULATION
RECEIVEDWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241

MAR 3 1988

BOB GRAHAM
GOVERNOR

DER-BAQM

VICTORIA J. TSCHINKEL
SECRETARY

APPLICATION TO OPERATE/CONSTRUCT AIR POLLUTION SOURCES

SOURCE TYPE: Stationary [] New¹ [X] Existing¹

APPLICATION TYPE: [] Construction [] Operation [X] Modification

COMPANY NAME: HARRIS SEMICONDUCTOR COUNTY: BrevardIdentify the specific emission point source(s) addressed in this application (i.e. Lime
Kiln No. 4 with Venturi Scrubber; Peaking Unit No. 2, Gas Fired) B-54 Manufacturing FabSOURCE LOCATION: Street Palm Bay Road City Palm BayUTM: East 17-538700 North 17-3100900Latitude 28 ° 01 ' 20 "N Longitude 80 ° 36 ' 10 "WAPPLICANT NAME AND TITLE: J. R. Kolanek, Manager Environmental ServicesAPPLICANT ADDRESS: P.O. Box 883, Melbourne, Florida 32901

SECTION I: STATEMENTS BY APPLICANT AND ENGINEER

A. APPLICANT

I am the undersigned owner or authorized representative* of HARRIS SEMICONDUCTORI certify that the statements made in this application for a modified
permit are true, correct and complete to the best of my knowledge and belief. Further,
I agree to maintain and operate the pollution control source and pollution control
facilities in such a manner as to comply with the provision of Chapter 403, Florida
Statutes, and all the rules and regulations of the department and revisions thereof. I
also understand that a permit, if granted by the department, will be non-transferable
and I will promptly notify the department upon sale or legal transfer of the permitted
establishment.

*Attach letter of authorization

Signed: James R. Kolanek
J. R. Kolanek, Manager, Environmental Services
Name and Title (Please Type)Date: 3-2-88 Telephone No. (305) 724-7467

B. PROFESSIONAL ENGINEER REGISTERED IN FLORIDA (where required by Chapter 471, F.S.)

This is to certify that the engineering features of this pollution control project have
been designed/examined by me and found to be in conformity with modern engineering
principles applicable to the treatment and disposal of pollutants characterized in the
permit application. There is reasonable assurance, in my professional judgment, that

See Florida Administrative Code Rule 17-2.100(57) and (104)

the pollution control facilities, when properly maintained and operated, will discharge an effluent that complies with all applicable statutes of the State of Florida and the rules and regulations of the department. It is also agreed that the undersigned will furnish, if authorized by the owner, the applicant a set of instructions for the proper maintenance and operation of the pollution control facilities and, if applicable, pollution sources.

Signed Lawrence R. Hutker

Lawrence R. Hutker

Name (Please Type)

HARRIS SEMICONDUCTOR

Company Name (Please Type)

P.O. Box 883, Melbourne, FL 32901

Mailing Address (Please Type)

Florida Registration No. 35972 Date: 3-2-88 Telephone No. (305) 729-4655

SECTION II: GENERAL PROJECT INFORMATION

A. Describe the nature and extent of the project. Refer to pollution control equipment, and expected improvements in source performance as a result of installation. State whether the project will result in full compliance. Attach additional sheet if necessary.

This is a modification and consolidation of existing air permits.

B. Schedule of project covered in this application (Construction Permit Application Only)

Start of Construction N/A Completion of Construction N/A

C. Costs of pollution control system(s): (Note: Show breakdown of estimated costs only for individual components/units of the project serving pollution control purposes. Information on actual costs shall be furnished with the application for operation permit.)

N/A

D. Indicate any previous DER permits, orders and notices associated with the emission point, including permit issuance and expiration dates.

AO 05-65408 issued 5/3/83 expires 5/2/88

AO 05-115804 issued 5/20/86 expires 5/22/91

E. Requested permitted equipment operating time: hrs/day 24; days/wk 7; wks/yr 52; if power plant, hrs/yr _____; if seasonal, describe: _____

F. If this is a new source or major modification, answer the following questions. (Yes or No)

1. Is this source in a non-attainment area for a particular pollutant? No
a. If yes, has "offset" been applied? _____
b. If yes, has "Lowest Achievable Emission Rate" been applied? _____
c. If yes, list non-attainment pollutants. _____

2. Does best available control technology (SACT) apply to this source? If yes, see Section VI. No

3. Does the State "Prevention of Significant Deterioration" (PSD) requirement apply to this source? If yes, see Sections VI and VII. No

4. Do "Standards of Performance for New Stationary Sources" (NSPS) apply to this source? No

5. Do "National Emission Standards for Hazardous Air Pollutants" (NESHAP) apply to this source? No

H. Do "Reasonably Available Control Technology" (RACT) requirements apply to this source? No

a. If yes, for what pollutants? _____

b. If yes, in addition to the information required in this form, any information requested in Rule 17-2.650 must be submitted.

Attach all supportive information related to any answer of "Yes". Attach any justification for any answer of "No" that might be considered questionable.

SECTION III: AIR POLLUTION SOURCES & CONTROL DEVICES (Other than Incinerators)

A. Raw Materials and Chemicals Used in your Process, if applicable:

Description	Contaminants		Utilization Rate - lbs/hr	Relate to Flow Diagram
	Type	% wt.		
SEE ATTACHMENT	C			

B. Process Rate, if applicable: (See Section V, Item 1)

1. Total Process Input Rate (lbs/hr): not applicable

2. Product Weight (lbs/hr): not applicable

C. Airborne Contaminants Emitted: (Information in this table must be submitted for each emission point, use additional sheets as necessary)

Name of Contaminant	Emission ¹		Allowed Emission Rate per Rule 17-2	Allowable ³ Emission lbs/hr	Potential ⁴ Emission		Relate to Flow Diagram
	Maximum lbs/hr	Actual T/yr			lbs/yr	T/yr	
SEE ATTACHMENT B							

¹See Section V, Item 2.

²Reference applicable emission standards and units (e.g. Rule 17-2.600(5)(b)2. Table II, E. (1) - 0.1 pounds per million BTU heat input)

³Calculated from operating rate and applicable standard.

⁴Emission, if source operated without control (See Section V, Item 3).

J. Control Devices: (See Section V, Item 4)

Name and Type (Model & Serial No.)	Contaminant	Efficiency	Range of Particles Size Collected (in microns) (If applicable)	Basis for Efficiency (Section V Item 5)
SEE ATTACHMENT D				

E. Fuels not applicable

Type (Be Specific)	Consumption*		Maximum Heat Input (MMBTU/hr)
	avg/hr	max./hr	

*Units: Natural Gas--MMCF/hr; Fuel Oils--gallons/hr; Coal, wood, refuse, other--lbs/hr.

Fuel Analysis:

Percent Sulfur: _____ Percent Ash: _____

Density: _____ lbs/gal Typical Percent Nitrogen: _____

Heat Capacity: _____ BTU/lb _____ BTU/gal

Other Fuel Contaminants (which may cause air pollution): _____

F. If applicable, indicate the percent of fuel used for space heating.

Annual Average _____ Maximum _____

G. Indicate liquid or solid wastes generated and method of disposal.

Waste water from air scrubbers is discharged to on-site waste water treatment plant.

Discharge to deep well under UIC-Permit #UC05-126519.

SEE ATTACHEMENT D

H. Emission Stack Geometry and Flow Characteristics (Provide data for each stack):

Stack Height: _____ ft. Stack Diameter: _____ ft.
 Gas Flow Rate: _____ ACFM _____ DSCFM Gas Exit Temperature: _____ °F.
 Water Vapor Content: _____ % Velocity: _____ FPS

SECTION IV: INCINERATOR INFORMATION
 not applicable

Type of Waste	Type 0 (Plastics)	Type I (Rubbish)	Type II (Refuse)	Type III (Garbage)	Type IV (Pathological)	Type V (Liq. & Gas By-prod.)	Type VI (Solid By-prod.)
Actual lb/hr Incinerated							
Uncontrolled (lbs/hr)							

Description of Waste _____

Total Weight Incinerated (lbs/hr) _____ Design Capacity (lbs/hr) _____

Approximate Number of Hours of Operation per day _____ day/wk _____ wks/yr. _____

Manufacturer _____

Date Constructed _____ Model No. _____

	Volume (ft) ³	Heat Release (BTU/hr)	Fuel		Temperature (°F)
			Type	BTU/hr	
Primary Chamber					
Secondary Chamber					

Stack Height: _____ ft. Stack Diameter: _____ Stack Temp. _____

Gas Flow Rate: _____ ACFM _____ DSCFM* Velocity: _____ FPS

*If 50 or more tons per day design capacity, submit the emissions rate in grains per standard cubic foot dry gas corrected to 50% excess air.

Type of pollution control device: Cyclone Wet Scrubber Afterburner
 Other (specify) _____

Brief description of operating characteristics of control devices: _____

Ultimate disposal of any effluent other than that emitted from the stack (scrubber water, ash, etc.):

NOTE: Items 2, 3, 4, 6, 7, 8, and 10 in Section V must be included where applicable.

SECTION V: SUPPLEMENTAL REQUIREMENTS

Please provide the following supplements where required for this application.

1. Total process input rate and product weight -- show derivation [Rule 17-2.100(127)]
2. To a construction application, attach basis of emission estimate (e.g., design calculations, design drawings, pertinent manufacturer's test data, etc.) and attach proposed methods (e.g., FR Part 60 Methods 1, 2, 3, 4, 5) to show proof of compliance with applicable standards. To an operation application, attach test results or methods used to show proof of compliance. Information provided when applying for an operation permit from a construction permit shall be indicative of the time at which the test was made.
3. Attach basis of potential discharge (e.g., emission factor, that is, AP42 test).
4. With construction permit application, include design details for all air pollution control systems (e.g., for baghouse include cloth to air ratio; for scrubber include cross-section sketch, design pressure drop, etc.)
5. With construction permit application, attach derivation of control device(s) efficiency. Include test or design data. Items 2, 3 and 5 should be consistent: actual emissions = potential (1-efficiency).
6. An 8 1/2" x 11" flow diagram which will, without revealing trade secrets, identify the individual operations and/or processes. Indicate where raw materials enter, where solid and liquid waste exit, where gaseous emissions and/or airborne particles are evolved and where finished products are obtained.
7. An 8 1/2" x 11" plot plan showing the location of the establishment, and points of airborne emissions, in relation to the surrounding area, residences and other permanent structures and roadways (Example: Copy of relevant portion of USGS topographic map).
8. An 8 1/2" x 11" plot plan of facility showing the location of manufacturing processes and outlets for airborne emissions. Relate all flows to the flow diagram.

9. The appropriate application fee in accordance with Rule 17-4.05. The check should be made payable to the Department of Environmental Regulation.
10. With an application for operation permit, attach a Certificate of Completion of Construction indicating that the source was constructed as shown in the construction permit.

SECTION VI: BEST AVAILABLE CONTROL TECHNOLOGY

A. Are standards of performance for new stationary sources pursuant to 40 C.F.R. Part 60 applicable to the source?

Yes No

Contaminant	Rate or Concentration
_____	_____
_____	_____
_____	_____

B. Has EPA declared the best available control technology for this class of sources (If yes, attach copy)

Yes No

Contaminant	Rate or Concentration
_____	_____
_____	_____
_____	_____

C. What emission levels do you propose as best available control technology?

Contaminant	Rate or Concentration
_____	_____
_____	_____
_____	_____

D. Describe the existing control and treatment technology (if any).

- | | |
|---------------------------|--------------------------|
| 1. Control Device/System: | 2. Operating Principles: |
| 3. Efficiency:* | 4. Capital Costs: |

*Explain method of determining

5. Useful Life:
7. Energy:
9. Emissions:

6. Operating Costs:
8. Maintenance Cost:

Contaminant

Rate or Concentration

Contaminant	Rate or Concentration

10. Stack Parameters

- | | | | |
|---------------|------|-----------------|-----|
| a. Height: | ft. | b. Diameter: | ft. |
| c. Flow Rate: | ACFM | d. Temperature: | °F. |
| e. Velocity: | FPS | | |

E. Describe the control and treatment technology available (As many types as applicable, use additional pages if necessary).

1.

- | | |
|-----------------------------|--------------------------|
| a. Control Device: | b. Operating Principles: |
| c. Efficiency: ¹ | d. Capital Cost: |
| e. Useful Life: | f. Operating Cost: |
| g. Energy ² | h. Maintenance Cost: |
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

2.

- | | |
|-----------------------------|--------------------------|
| a. Control Device: | b. Operating Principles: |
| c. Efficiency: ¹ | d. Capital Cost: |
| e. Useful Life: | f. Operating Cost: |
| g. Energy: ² | h. Maintenance Cost: |
- i. Availability of construction materials and process chemicals:

¹Explain method of determining efficiency.

²Energy to be reported in units of electrical power - KWH design rate.

- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

3.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Cost:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

4.

- a. Control Device:
- b. Operating Principles:
- c. Efficiency:¹
- d. Capital Costs:
- e. Useful Life:
- f. Operating Cost:
- g. Energy:²
- h. Maintenance Cost:
- i. Availability of construction materials and process chemicals:
- j. Applicability to manufacturing processes:
- k. Ability to construct with control device, install in available space, and operate within proposed levels:

F. Describe the control technology selected:

- 1. Control Device:
- 2. Efficiency:¹
- 3. Capital Cost:
- 4. Useful Life:
- 5. Operating Cost:
- 6. Energy:²
- 7. Maintenance Cost:
- 8. Manufacturer:
- 9. Other locations where employed on similar processes:
- a. (1) Company:
- (2) Mailing Address:
- (3) City:
- (4) State:

¹ Explain method of determining efficiency.

Energy to be reported in units of electrical power - KWH design rate.

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant

Rate or Concentration

(8) Process Rate:¹

b. (1) Company:

(2) Mailing Address:

(3) City:

(4) State:

(5) Environmental Manager:

(6) Telephone No.:

(7) Emissions:¹

Contaminant

Rate or Concentration

(8) Process Rate:¹

10. Reason for selection and description of systems:

¹Applicant must provide this information when available. Should this information not be available, applicant must state the reason(s) why.

SECTION VII - PREVENTION OF SIGNIFICANT DETERIORATION not applicable

A. Company Monitored Data

1. _____ no. sites _____ TSP _____ () SO₂+ _____ Wind spd/dir

Period of Monitoring _____ / _____ / _____ to _____ / _____ / _____
month day year month day year

Other data recorded _____

Attach all data or statistical summaries to this application.

Specify bubbler (B) or continuous (C).

2. Instrumentation, Field and Laboratory

- a. Was instrumentation EPA referenced or its equivalent? Yes No
- b. Was instrumentation calibrated in accordance with Department procedures?
 Yes No Unknown

B. Meteorological Data Used for Air Quality Modeling

- 1. _____ Year(s) of data from _____ / _____ / _____ to _____ / _____ / _____
month day year month day year
- 2. Surface data obtained from (location) _____
- 3. Upper air (mixing height) data obtained from (location) _____
- 4. Stability wind rose (STAR) data obtained from (location) _____

C. Computer Models Used

- 1. _____ Modified? If yes, attach description.
- 2. _____ Modified? If yes, attach description.
- 3. _____ Modified? If yes, attach description.
- 4. _____ Modified? If yes, attach description.

Attach copies of all final model runs showing input data, receptor locations, and principle output tables.

D. Applicants Maximum Allowable Emission Data

Pollutant	Emission Rate
TSP	_____ grams/sec
SO ²	_____ grams/sec

E. Emission Data Used in Modeling

Attach list of emission sources. Emission data required is source name, description of point source (on NEDS point number), UTM coordinates, stack data, allowable emissions, and normal operating time.

F. Attach all other information supportive to the PSD review.

G. Discuss the social and economic impact of the selected technology versus other applicable technologies (i.e., jobs, payroll, production, taxes, energy, etc.). Include assessment of the environmental impact of the sources.

H. Attach scientific, engineering, and technical material, reports, publications, journals, and other competent relevant information describing the theory and application of the requested best available control technology.

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT A

Process Description

Attachment A

Building 54 is a wafer fabrication facility. The second floor of the two-story building houses two clean room modules. Both fabrication areas employ a series of manufacturing procedures referred to as layering, patterning, doping and heating processes. The frequency and sequence of these processes can vary depending on the desired nature of the final product.

In the controlled environment of the fabrication clean rooms, wafer surfaces first undergo acid and/or solvent cleaning, followed by thermal oxidation in furnaces to form a layer of silicon dioxide on the wafer surface.

During the patterning process, the wafers are initially baked and primed. Coaters then spin a thin layer of "photoresist" on the wafer, after which the wafers are soft baked. Next, the circuit pattern is projected onto the wafers via "alligners" or "steppers." Developers are then applied to remove unpolymerized areas of photoresist. This is followed by a solvent rinse.

Next, the wafers hard-baked, inspected to determine accuracy, and etched by wet (acid bath) or dry (plasma vapor) mechanisms. Once etching is complete, the photoresist is stripped off the wafer using chemical baths or plasma techniques.

In another step of the fabrication process, "dopant" atoms are either diffused into the wafer in diffusion furnaces, or accelerated into the wafer using "ion implantation." Additional material may be layered on the wafer surface in vapor and crystal (epitaxial) deposition furnaces. Metallization to interconnect uppermost circuit layers is performed by deposition (using "sputtering" systems) or evaporation.

Wet stations that house vats containing a variety of acid and caustic compounds are located throughout the clean rooms. Storage cabinets safely hold virgin chemicals until they are ready for use. The first floor of the building contains exhausted gas cabinets that supply process gases to the 'fab' operations.

The exhaust system for the building is divided into two sections. The west half exhaust is fed into a common duct that is divided into two wet scrubber systems, F54S01 and F54S02, at ground level. The east portion of the building exhaust is ducted a common line that divides into two wet scrubbers (F54S03 and F54S04) on the east side of building (see attachment E.) Also on the east side of building 54 is a non-scrubbed exhaust fan F54E17 that handles air flow from several alligners, furnace source cabinets, and gas cabinets.

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT B

Air Emissions

Attachment B

Monitoring work was performed on the building 54 scrubber systems in August and November of 1987. Tests conducted included EPA methods 25A (flame ionization detector) and TO-1 (Tenax adsorption and GC/MS analysis.) The results of this testing is included in this application.

FID test results revealed that total accumulative monitored VOC emissions for the building were 82.58 tons/year expressed as propane. This figure includes off-shift emissions and is based on a 8760 day a year production schedule for the east fab and a 4160 day a year production schedule for the west. The following assumptions were made regarding monitoring work on this building:

- Emission values for F54S02 & F54S04 are assumed to be equal to F54S01 & F54S03, respectively. This is because each pair handle exhaust from a common duct.
- VOC values refer to all organic emissions including organic solvents.
- Nonproduction emissions are assumed to be 18.3% of production emissions, as was found to be the case when scrubber F54S01 was monitored on a day of no production in the fabrication area.
- Nonproduction emissions are based on a 13% scrubber removal efficiency.
- All data is corrected for 2 ppm background concentration of VOC's that is present in the ambient air.
- The F.I.D. accumulative emission figure is based on the maximum concentration observed during the monitoring timeframe.

Total projected VOC emissions for building 54 is 94.34 tons/year. This number is representative of maximum VOC emissions, and is derived from the following proportion:

$$\frac{82.58 \text{ tpy}}{131.29 \text{ tpy}} = \frac{94.34 \text{ tpy}}{150.00 \text{ tpy}}$$

- where:
- 82.58 tpy is the maximum building emissions determined by EPA Method 25-A monitoring.
 - 131.29 tpy is the maximum Semiconductor site emissions determined by EPA Method 25-A monitoring.
 - 150.00 tpy is the established site emission limit for VOC's.

EPA METHOD 25-A (F.I.D. ANALYSIS) BUILDING 54
EMISSIONS DURING PRODUCTION HOURS

TEST DATE	F54S01 (TON/YR)	F54S02 (TON/YR)	F54S03 (TON/YR)	F54S04 (TON/YR)
08/20/87	5.36	5.36	---	---
08/21/87	---	---	25.4	25.4
11/14/87	---	---	30.22	30.22
11/22/87	---	---	32.59	32.59
11/23/87	7.24	7.24	---	---

NOTE: ABOVE BASED ON ACTUAL OPERATING HOURS.

TOTAL VOC EMISSIONS FROM BUILDING 54
AS DETECTED BY EPA METHOD 25-A

SCRUB#	PRODUCTN SCHEDULE	NONPRODUCTN SCHEDULE	PRODUCTN EMISSIONS (TON/YR)	NONPRODUCTN EMISSIONS (TON/YR)	TOTAL MONITORED VOC EMISSIONS* (TON/YR)
F54S01	4160	4600	7.24	1.47	8.70
F54S02	4160	4600	7.24	1.47	8.70
F54S03	8760	0	32.59	0	32.59
F54S04	8760	0	32.59	0	32.59

* BASED ON MAXIMUM CONCENTRATIONS OBSERVED.

TOTAL PROJECTED VOC EMISSIONS FOR BLDG. 54 = 94.34 TONS/YEAR

EPA METHOD TO-1: GC/MS ANALYSIS

AUGUST RESULTS-

	-----SCRUBBER #-----			
	F54S01	F54S02	F54S03	F54S04
ACETONE (LB/HR)	1.23	1.23	3.18	3.18
TRICHLOROETHANE (LB/HR)	---	---	0.33	0.33
METHYLENE CHLORIDE (LB/HR)	trace	trace	---	---
TETRACHLOROMETHYLENE (LB/HR)	---	---	0.17	0.17
FREON-113 (LB/HR)	0.02	0.02	0.07	0.07
CHLOROFORM (LB/HR)	trace	trace	---	---
BENZENE (LB/HR)	trace	trace	trace	trace
TRICHLOROETHYLENE (LB/HR)	trace	trace	trace	trace
TOLUENE (LB/HR)	trace	trace	trace	trace
METHYL ISOBUTYL KETONE (LB/HR)	---	---	---	---
ETHYL BENZENE (LB/HR)	---	---	---	---
XYLENES (LB/HR)	---	---	---	---

NOVEMBER RESULTS-

	F54S01	F54S02	F54S03	F54S04
ACETONE (LB/HR)	---	---	2.10	2.10
XYLENES (LB/HR)	---	---	0.66	0.66
ETHYL BENZENE (LB/HR)	---	---	0.15	0.15
1,2-DICHLOROBENZENE (LB/HR)	---	---	0.85	0.85
1,1-DICHLOROETHENE (LB/HR)	---	---	0.07	0.07
TETRACHLOROETHENE (LB/HR)	---	---	2.02	2.02
1,1,1-TRICHLOROETHANE	---	---	6.10	6.10

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT C

Raw Materials and Chemicals

PROCESS CHEMICALS

1. ACETIC ACID
2. AMMONIUM FLUORIDE
3. AMMONIA
4. AMMONIUM HYDROXIDE
5. ETHYLENE GLYCOL
6. GLYCERINE
7. HYDROFLUORIC ACID
8. HYDROCHLORIC ACID
9. HYDROGEN PEROXIDE
10. NITRIC ACID
11. PHOSPHORIC ACID
12. POTASSIUM HYDROXIDE
13. SODIUM HYDROXIDE
14. SULFURIC ACID
15. CHROMIC ACID
16. TETRAMETHYL AMMONIUM HYDROXIDE
17. ETHYLENE DIAMINE TETRACETIC ACID (EDTA)
18. DODECYLBENZENE SULFONIC ACID
19. ALKYL ARYL SULFONIC ACID
20. CERIC SULFATE
21. SODIUM HYPOPHOSPHITE
22. PHOSPHATE
23. ALUMINA SILICA

PROCESS GASES

1. ARGON
2. ARSINE
3. BORON TRIBROMIDE
4. BORON TRICHLORIDE
5. BORON TRIFLUORIDE
6. CARBON DIOXIDE
7. CHLORINE
8. DIBORANE
9. DICHLOROSILANE
10. HELIUM
11. HYDROGEN CHLORIDE
12. HYDROGEN
13. NITROGEN
14. NITROGEN TRIFLUORIDE
15. NITROUS OXIDE
16. OXYGEN
17. PHOSPHINE
18. PHOSPHOROUS OXYCHLORIDE
19. PHOSPHOROUS TRIBROMIDE
20. SILANE
21. SULFUR HEXAFLUORIDE
22. TUNGSTEN HEXAFLUORIDE
23. DE 100
24. PDE 100

PROCESS CHEMICALS

SOLVENTS

1. 1,1,1 TRICHLOROETHANE
2. ACETONE
3. BUTYL CELLOSOLVE
4. CELLOSOLVE ACETATE
5. CARBON TETRACHLORIDE
6. FREON 116
7. FREON 14
8. FREON 23
9. FREON TF
10. HEXAMETHYLDISILIZANE
11. ISOPROPYL ALCOHOL
12. METHANOL
13. N-BUTYL ACETATE
14. XYLENE
15. ETHYL BENZENE
16. 2-ETHOXYETHYL ACETATE
17. 1,2,4 TRICHLOROBENZENE
18. AROMATIC PHENOL
19. CRESOL
20. OIL
21. ISOPARAFFINIC HYDROCARBONS
22. OXYLPHENOL POLYETHOXYLATE
23. PROPYLENE GLYCOL MONOETHYL ETHER ACETATE
24. 1,1,1 TRIMETHYL-N-TRIMETHYL ETHER
25. PHILTEC SAFETY STAIN

HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT D

Control Equipment

SCRUBBER INFORMATION

HARRIS ID # : F54501
MANUFACTURER : HARRISON MODEL NUMBER : HF-200
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 95 MAKE UP RATE (GPM): 9.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): NR MAKE UP RATE (GPM): 5 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : A. O. SMITH MODEL NUMBER : P48K2EB7B2
SERIAL NUMBER: N/A HP : 1 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : P

FAN INFORMATION

HARRIS ID # : F54E01
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-FP3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD INCLINED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 STATIC PRESS (IN): 3.3

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 30 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : U

SCRUBBER INFORMATION

HARRIS ID # : F54S02
MANUFACTURER : HARRISON MODEL NUMBER : HF-200
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 95 MAKE UP RATE (GPM): 9.0

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): 30 MAKE UP RATE (GPM): 5.0 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : FRANKLIN ELECTRIC MODEL NUMBER : 1303012101
SERIAL NUMBER: N/A HP : 1/2 RPM : 3450
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : P

FAN INFORMATION

HARRIS ID # : F54E02
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-FP3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD CURVED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 20,000 STATIC PRESS (IN): 3.3

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 30 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : U

SCRUBBER INFORMATION

HARRIS ID # : F54S03
MANUFACTURER : HARRISON MODEL NUMBER : HF-230
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 23,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 112 MAKE UP RATE (GPM): 11

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): 30 MAKE UP RATE (GPM): 10 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : GENERAL ELECT. MODEL NUMBER : SKFG2666
SERIAL NUMBER: HP : 1/3 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S, I

FAN INFORMATION

HARRIS ID # : F54E12
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-GS3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD CURVED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 26,500 STATIC PRESS (IN): 5.6

ACTUAL DATA

VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 40 RPM : 1287
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S, U

SCRUBBER INFORMATION

HARRIS ID # : F54S04
MANUFACTURER : HARRISON MODEL NUMBER : HF-230
SERIAL NUMBER: N/A MATERIAL : POLYPRO
DESCRIPTION : HORIZONTAL CROSS-FLOW, PLASTIC SADDLE PACKING, LIQUID
DISTRIBUTION THROUGH MAIN HEADER, NO SPRAY NOZZLES

DESIGN DATA

VOLUME FLOW RATE (CFM): 23,000 PRESSURE DROP (IN):
RECIRCULATION RATE (GPM): 112 MAKE UP RATE (GPM): 11

ACTUAL DATA

VOLUME FLOW RATE (CFM): PRESSURE DROP (IN): N/E DATE: 06/03/87
RECIRCULATION RATE (GPM): 70 MAKE UP RATE (GPM): 10 DATE: "

RECIRCULATION PUMP INFORMATION

MANUFACTURER : GENERAL ELECT. MODEL NUMBER : 5K42FG2666
SERIAL NUMBER: N/A HP : 1/3 RPM : 1725
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S,I

FAN INFORMATION

HARRIS ID # : F54E13
MANUFACTURER : HARTZELL MODEL NUMBER: 41-40-GS3
SERIAL NUMBER: N/A MATERIAL : FIBERGLASS
DESCRIPTION : CENTRIFUGAL BLOWER, BACKWARD CURVED BLADES

DESIGN DATA

VOLUME FLOW RATE (CFM): 26,500 STATIC PRESS (IN): 5.6

ACTUAL DATA

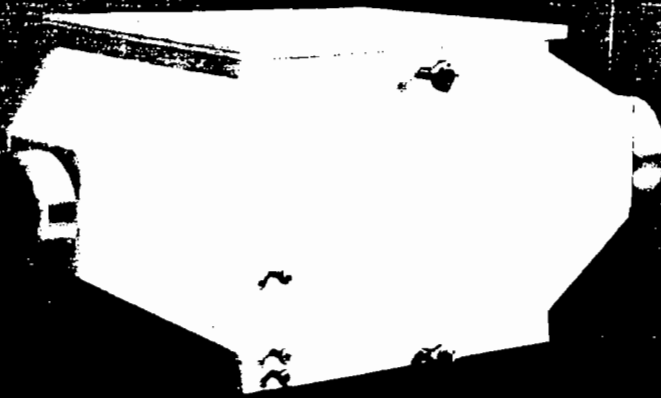
VOLUME FLOW RATE (CFM): SPEED (RPM): DATE:
STATIC PRESS (IN): DATE:

FAN MOTOR INFORMATION

MANUFACTURER : MODEL NUMBER :
SERIAL NUMBER: HP : 40 RPM : 1287
BRKR LOCATION: NEXT TO UNIT FED FROM MCC : S,U

Attachment :

Plastic Packed Scrubbers



THE HARRISON SYSTEM

Harrison is a prime designer and producer of complete plastic exhaust systems, custom engineered scrubbing systems, as well as duct and fittings, tanks, and hoods. As a result of this capability and experience, design and manufacture of standard, pre-engineered fume scrubbers is a natural extension.

MATERIALS

Self-supporting or fiberglass armored PVC and Polypropylene, fiberglass armored Kynar, and solid fiberglass construction offers a wide range of resistance to acids, alkalis, solvents, and other corrosives at operating temperatures to approximately 250°F. Harrison systems do not use any metal in contact with the process stream.

PRE-ENGINEERING

Pre-engineered design reduces cost by eliminating the necessity to re-invent each item ordered. It results in more reliable service thru improved workmanship achieved by repetitive production control, and speeds quotations and approval drawings because costs and designs are immediately available. In addition to significant savings in approval and order time, Harrison reduces delivery time by stocking scrubber components including packing, support grids, distributor plates, nozzles, duct reducers, and sheet stock.

SCRUBBER CONFIGURATION

Most fume removal applications can be served by the two scrubber designs shown in this catalog. Vertical Counter Current style directs liquid down vertically, and unwanted fumes upward in the opposite direction. Horizontal Cross Flow unit directs liquid down vertically, but unwanted fumes are driven horizontally at 90° to the liquid. In both designs, liquid and fumes are inter-mixed in the packed bed section of the scrubber where fumes are removed by chemical reaction or water solubility. Scrubber shape does not affect performance. Horizontal design presents a low profile and is suitable where head room is limited. Verticals require more head room, but use only minimum floor space.

SCRUBBER DESIGN AND OPERATION

Highest scrubber efficiency (volumetric % of contaminate removed) is obtained by having the proper amount of contact surface area (packing) wetted by sufficient liquid (recirculated liquid rate) for an optimum residence time (packing depth) to allow unwanted fumes to take a treacherous path thru the wetted packing to permit their maximum removal from the carrier air stream by chemical reaction or water solubility.

Air stream resistance encountered in the packing (static pressure loss) is a function of air velocity, cross-sectional packing area, and packing depth. Harrison scrubbers utilize proven packing depth to achieve efficiencies approaching 99+%, when operated within recommendations.

LIQUID DISTRIBUTION AND MIST ELIMINATION

Simple liquid distribution is achieved thru a main header pipe feeding perforated laterals without use of troublesome spray nozzles. Nozzles are subject to plugging, and produce a difficult-to-remove atomized mist carryover. In the Harrison design, any large droplets of liquid caught in the upward moving air stream are easily and efficiently removed by a short bed of dry packing located above the liquid distributor.

STATIC PRESSURE LOSS

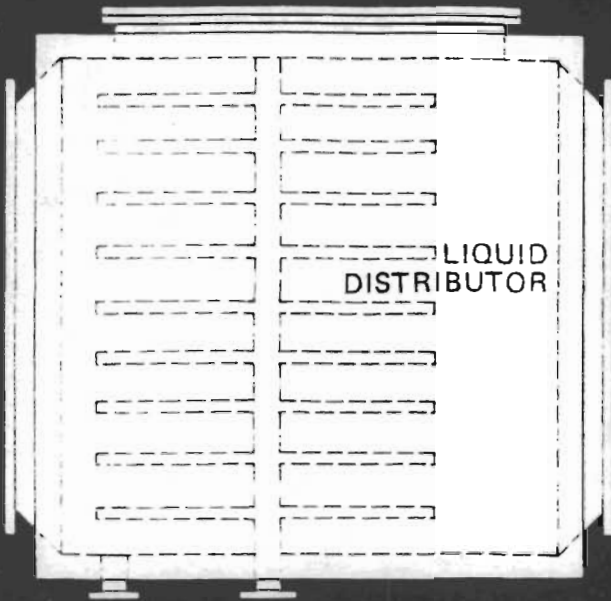
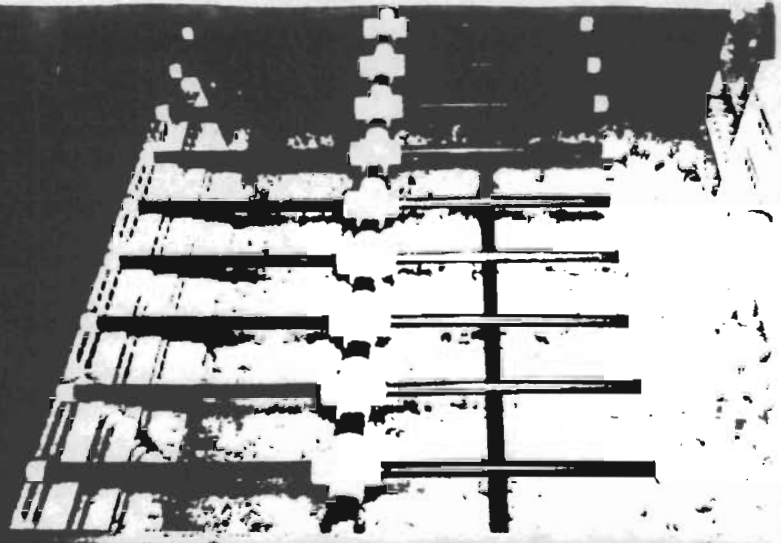
Use of high-surface-area, low-pressure-drop plastic saddles in a balanced design result in low static pressure loss of only 0.4 inches H₂O (w.g.) per foot of packed depth in Vertical Counter Current scrubbers, and 0.33 in Horizontal Cross Flow units. At the same time, sufficient irrigation rates constantly keep saddles clear of potential sludge buildup. Thereby, continuous, non-clogging operation at a proper rate of intermixing turbulence between liquid and fumes is achieved for 99+% efficiency.

LIQUID SUMP OPERATION

Harrison scrubbers employ an integral liquid recirculating sump which reduces amount of liquid consumption required by 90 to 95% in most applications. Therefore, considerably less effluent must be handled and treated. The sump reservoir is contained within the scrubber itself. Harrison recommends optimum rate of effluent removal. When effluent is acidic only, additional liquid conservation can be obtained with either scrubber design with the simple optional recovery system shown with the vertical scrubber drawing on page 4. If central treating facilities exist, no sump, recirculation, or independent recovery is needed. In this case, treated liquid would be directed over the packing in a single pass, then treated, then returned to the scrubber, etc. In both instances where effluent is treated, liquid consumption would be reduced to only that amount lost by evaporation.

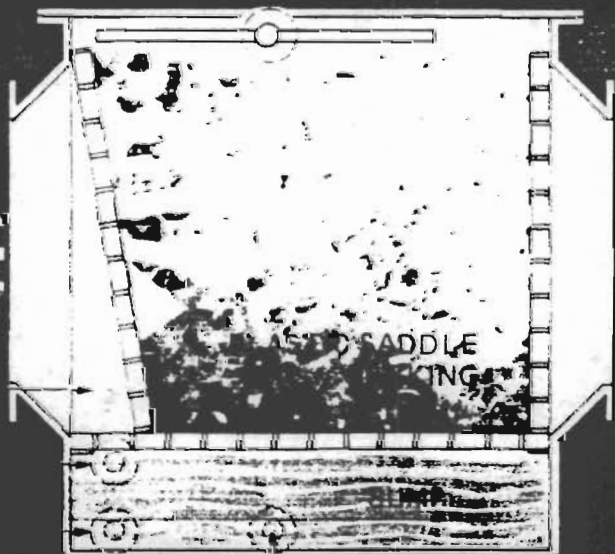
Harrison

Box 184 Aurora Ohio 44202/216-562-9545



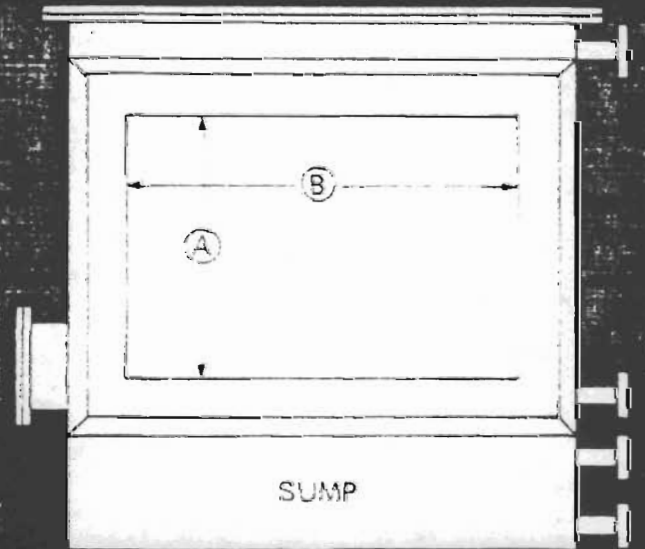
LIQUID
DISTRIBUTOR

TOP VIEW



SADDLE

SIDE VIEW (CUT-A-WAY)



SUMP

INLET SIDE VIEW

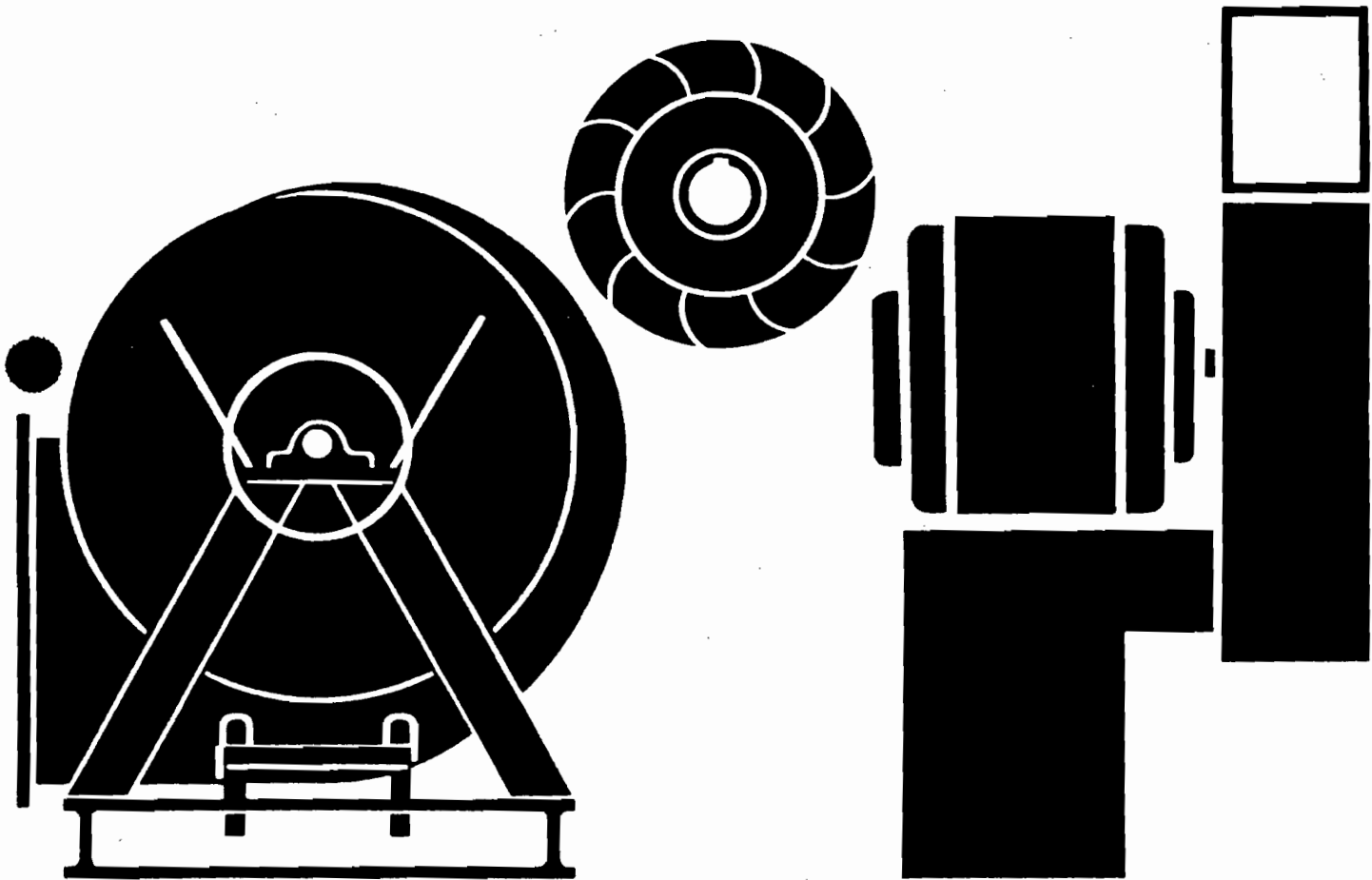
HORIZONTAL CROSS-FLOW

Model	CFM	Inlet & Outlet A x B In.	Length L Ft.	Width W In.	C In.	D In.	E In.	F In.	G In.	Sump Capacity Gal.	Rec. Liquid GPM	Overall Height In.	Ship* Wt. Lbs.	Operating Wt. Lbs.
HF-8	800	11x11	6	17	¾	1	1	1¼	1	58	17	35	182	646
HF-12	1,200	14x14	6	20	¾	1	1	1¼	1	69	21	38	224	781
HF-17	1,700	18x18	6	24	¾	1	1	1½	1¼	82	24	42	275	926
HF-21	2,100	21x21	6	27	¾	1	1	1½	1¼	92	28	45	316	1028
HF-25	2,500	24x24	6	30	¾	1½	1½	1½	1¼	102	32	48	357	1166
HF-31	3,100	27x27	6	33	¾	1½	1½	1½	1¼	113	35	51	419	1313
HF-37	3,700	30x30	6	36	¾	1½	1½	1½	1¼	125	39	54	481	1445
HF-45	4,500	33x33	6	39	¾	1½	1½	1½	1¼	134	42	57	563	1669
HF-50	5,000	36x36	6	42	¾	1½	1½	1½	1¼	144	45	5.0 ft.	615	1733
HF-67	6,700	36x36	6	48	1	2	2	1½	1¼	165	51	5.5	690	1980
HF-85	8,500	42x42	6	54	1	2	2	2	1½	186	56	6.0	824	2276
HF-105	10,500	48x48	6	60	1	2	2	2	1½	206	60	6.5	1035	2639
HF-126	12,600	54x54	6	66	1	2	2	2	1½	228	68	7.0	1242	2990
HF-150	15,000	60x60	6	72	1	2	2	2½	2	247	74	7.5	1545	3460
HF-176	17,600	66x66	6	78	1	2	2	2½	2	268	80	8.0	1751	3803
HF-190	19,000	66x72	6	84	1	2	2	2½	2	280	86	8.0	1857	4151
HF-220	22,000	66x84	6	90	1	2	2	2½	2	308	90	8.0	2066	4770
HF-245	24,500	66x96	6	96	1	2	2	3	3	311	92	8.0	2124	5329
HF-273	27,300	76x96	6	102	1	2	2	3	3	342	96	8.0	2300	5820
HF-300	30,000	84x96	6	108	1	2	2	3	3	371	100	8.0	2480	6320
HF-327	32,700	96x96	6	114	1	2	2	3	3	405	107	8.0	2490	7340

BEST AVAILABLE COPY

berglass Centrifugal Blowers

W. K. OUSLEY INC
P. O. DRAWER 750
650 AVE. B, S.W.
WINTER HAVEN FLA. 33880
813 - 324-4000



HARTZELL[®]

Hartzell Fan, Division of Castle Hills Corporation, Piqua, Ohio

Construction Features

A variety of corrosion problems plague industry today. Fans and blowers made of coated steel or metals such as stainless and monel can handle some problem areas. However, reinforced fiberglass and resin construction will meet even the most challenging demands.

Fiberglass centrifugal blowers can be used in most applications where corrosive elements exist in fume and vapor form at temperatures less than 200° F. The resistance to corrosive elements is a major advantage, but the physical properties of fiberglass equipment offer these additional advantages.

- Fiberglass equipment weighs 25% less than comparable equipment made of carbon steel.
- Fiberglass has an extremely high strength-to-weight ratio, stronger than steel on a per-pound basis.
- Dimensional stability of fiberglass is excellent. Fiberglass air moving equipment will not become brittle at low temperatures and at 0° F. the laminated fiberglass will be stronger than at room temperature.
- Fiberglass equipment offers a distinct advantage in price over stainless and monel (as much as 1/3 in original cost) and offers longer service life and requires less maintenance.

Hartzell fiberglass equipment is identical, except for part thickness, in design, overall specs and performance to our standard lines. The following are standard Hartzell fiberglass construction features:

- Special corrosive resistant polyester resin having a Class I flame spread rate of 25 or less.
- All structural parts in the airstream are fiberglass and resin. All taped joints inside the shell or body are three layers of two ounce material. All internal surfaces are protected with a 10 mil thickness of chemical resistant, flame retardant gel coat and all external surfaces have a heavy coating of resin applied before assembly.
- Internal hardware is 300 series stainless steel. Shafts are type 304; bolts and screws are type 316. Monel shafting and hardware are available as an extra-cost option for applications such as hydrochloric, hydrofluoric, or sulfuric acids, which attack stainless.

Where metal is subject to attack by the corrosive elements being handled, all metal parts can be resin-coated after assembly.

- A fiberglass and neoprene shaft seal is placed where the shaft leaves the housing along with a neoprene shaft slinger between the seal and wheel on belt drive units. (Seal is not gas tight.)
- All fiberglass radial and backward curved wheels are of multi-piece construction bonded together with resin and fiberglass material.

Maximum temperature limitation is 200° F. on all centrifugal blowers.

- All internal mounting hardware is encapsulated with a layer of fiberglass and resin.

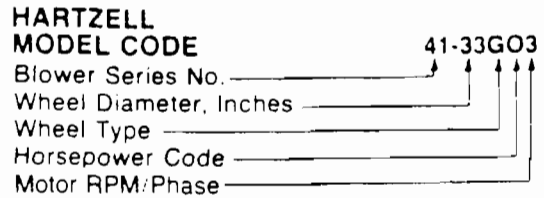
This bulletin lists Hartzell's complete line of fiberglass centrifugal blowers and accessories. More than 70 Hartzell offices can provide specific performance and installation data to meet your requirements. Call your nearest Hartzell representative for competent technical help.



Air Movement and Control Association Seal

Hartzell Propeller Fan Company certifies that the centrifugal blowers shown herein are licensed to bear the AMCA Seal. The ratings shown are based on tests made in accordance with AMCA Standard 210 and comply with the requirements of the AMCA Certified Ratings Program.

Selection Guide



3 Phase 1 Phase
 3 = 1750 C = 1750

How To Use Capacity Tables

- (1) Select size, RPM and BHP for a given air delivery and pressure of a centrifugal blower from rating tables, pages 10 through 21. Performance ratings are based on standard air conditions, sea level 70° F. and 29.92 inches barometric pressure giving an air density of .075 lbs. per cubic foot. The specific gravity of air equals 1.00 at these conditions.
- (2) If non-standard temperature or altitude is involved, correct to standard air density (see Table 1).
- (3) For speeds above ratings consult factory.

How to use Hartzell Model Code

EXAMPLE:

Assume the required performance to be 16,276 CFM at 3" SP standard air. Reading across the 33" Rating Table, page 13, we find a blower RPM of 1306 and brake horsepower of 14.5. Motor horsepower required is 15; therefore, horsepower code is "O". Type specification would be "GO3". The complete blower specification would read: Series 41-33-GO3.

Horsepower Code

Horsepower	¼	⅓	½	¾	1	1½	2	3	5	7½	10	15	20	25	30	40	50	60	75	100
Code Letter	D	E	F	G	H	I	J	K	L	M	N	O	P	Q	R	S	T	U	V	W

Altitude - Temperature Correction

Temperatures above or below 70° at sea level (0 ft.) are read vertically between the double lines, giving the proper correction factors. Altitudes above sea level at a constant 70° F. temperature are read horizontally between the double lines giving those factors. Any other factors are obtained by reading down to the desired temperature, then across to the desired altitude.

Example:

Assume the required performance to be 12,520 CFM at 6.15" SP, 175° F. and 2000 feet altitude.

1. Table 1 gives a factor of 1.30.

2. 6.15" SP × 1.30 = 8.0" SP for 70° F. at sea level.
3. A backward curved centrifugal blower, size 33", selected from the rating tables for the new condition shows 12,520 CFM at 8.0" SP, 1537 RPM and 23.9 BHP.
4. Correct the horsepower and static pressure in Item 3 to non-standard performance by dividing by the factor:
 $8.0" \text{ SP} \div 1.30 = 6.15 \text{ SP}$
 $23.9 \text{ BHP} \div 1.30 = 18.38 \text{ BHP}$
5. Final performance of this size 33" backward curved centrifugal blower at assumed conditions:
 12,520 CFM at 6.15" SP, 1537 RPM, 18.38 BHP, 175° F. and 2000 Ft.

Table 1 - Combined Altitude - Temperature Correction Factors

ALT. FT. / °F. TEMP.	0	1000	2000	3000	4000	5000	6000	7000	8000	9000	10000	11000	12000
-50	0.77	0.80	0.83	0.86	0.89	0.92	0.96	1.00	1.04	1.08	1.12	1.16	1.21
-25	0.82	0.85	0.89	0.92	0.95	0.98	1.03	1.07	1.11	1.15	1.20	1.24	1.29
0	0.87	0.90	0.94	0.97	1.01	1.04	1.09	1.13	1.17	1.22	1.27	1.31	1.37
25	0.91	0.95	0.98	1.02	1.06	1.09	1.14	1.18	1.23	1.27	1.33	1.37	1.43
50	0.96	1.00	1.04	1.08	1.11	1.15	1.20	1.25	1.30	1.34	1.40	1.45	1.51
70	1.00	1.04	1.08	1.12	1.16	1.20	1.25	1.30	1.35	1.40	1.46	1.51	1.57
100	1.06	1.10	1.14	1.19	1.23	1.27	1.33	1.38	1.43	1.48	1.55	1.60	1.66
125	1.10	1.14	1.19	1.23	1.28	1.32	1.38	1.43	1.49	1.54	1.61	1.66	1.73
150	1.15	1.20	1.24	1.29	1.33	1.38	1.44	1.50	1.55	1.61	1.68	1.74	1.81
175	1.20	1.25	1.30	1.34	1.39	1.44	1.50	1.56	1.62	1.68	1.75	1.81	1.88
200	1.25	1.30	1.35	1.40	1.45	1.50	1.56	1.63	1.69	1.75	1.83	1.89	1.96
250	1.34	1.39	1.45	1.50	1.55	1.61	1.68	1.74	1.81	1.88	1.96	2.02	2.10
300	1.43	1.49	1.54	1.60	1.66	1.72	1.79	1.86	1.93	2.00	2.09	2.16	2.25
350	1.53	1.59	1.65	1.71	1.77	1.84	1.91	1.99	2.07	2.14	2.23	2.31	2.40
400	1.62	1.69	1.75	1.82	1.89	1.96	2.04	2.12	2.20	2.27	2.35	2.45	2.55
450	1.72	1.79	1.86	1.93	2.00	2.08	2.16	2.24	2.33	2.41	2.50	2.60	2.70
500	1.81	1.88	1.96	2.03	2.11	2.19	2.28	2.36	2.46	2.54	2.62	2.74	2.85
550	1.91	1.98	2.06	2.14	2.22	2.30	2.40	2.49	2.58	2.68	2.77	2.89	3.00
600	2.00	2.08	2.16	2.24	2.33	2.42	2.50	2.61	2.71	2.80	2.90	3.03	3.14

NOTE: Above table has inverted values. Actual density is the reciprocal of the above values.

Abrasive/Erosive Atmospheres

HartKoate is an abrasive erosive resistant coating developed by Hartzell for application in environments where abrasive erosive conditions may exist. HartKoate helps prevent premature deterioration of equipment in environments where uncoated fans may fail.

Impact resistant HartKoate is applied to a 50-60 mil thickness suitable for temperatures to 200 F.

HartKoate is particularly appropriate for use when water mist and/or abrasive particles exist in the air stream.

Contact your Hartzell representative for further details concerning the application of HartKoate coating to fiberglass fans in corrosive atmospheres.

Installation Weights - Bearing/Shaft Sizes

Series 41

Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes												
15"	GH3	526	1 7/16"	40"	GI3	1885	2 7/16"	19"	FI3	372	1 7/16"	30"	FL3	626	1 5/16"												
	GI3	526	1 7/16"		GJ3	1885	2 7/16"		FJ3	372	1 7/16"		FM3	629	1 5/16"												
	GJ3	529	1 7/16"		GK3	1912	2 7/16"		FK3	399	1 7/16"		FN3	649	1 5/16"												
	GK3	529	1 7/16"		GL3	1932	2 7/16"		FL3	444	1 7/16"		FO3	709	1 5/16"												
	GL3	549	1 7/16"		GM3	1972	2 7/16"		FM3	447	1 7/16"		FP3	739	1 5/16"												
	GM3	554	1 7/16"		GN3	1987	2 7/16"		FN3	466	1 7/16"		FQ3	779	1 5/16"												
22"	GH3	772	1 11/16"	49"	GO3	2047	2 7/16"	23"	FO3	517	1 7/16"	33"	FR3	869	1 5/16"												
	GI3	772	1 11/16"		GP3	2077	2 7/16"		FP3	547	1 7/16"		FS3	909	1 5/16"												
	GJ3	776	1 11/16"		GQ3	2127	2 7/16"		FQ3	587	1 7/16"		FT3	1004	1 5/16"												
	GK3	776	1 11/16"		GR3	2177	2 7/16"		FR3	667	1 7/16"		FU3	529	1 5/16"												
	GL3	806	1 11/16"		GS3	2277	2 7/16"		26"	FK3	404		1 11/16"	Series 42	10"	FC3	63										
	GM3	813	1 11/16"		GT3	2327	2 7/16"			FL3	431		1 11/16"					12"	FF3	78							
	GN3	854	1 11/16"		Series 43	16"	FH3			302	1 3/16"		FL3								451	1 11/16"	14"	FG3	96		
	GO3	865	1 11/16"				GM3			2465	2 5/16"		FM3								496	1 11/16"				Series 42	
GP3	926	1 11/16"	GN3	2483			2 5/16"			FN3	516		1 11/16"								Series 42						
27"	GI3	954	1 15/16"	GO3			2558			2 5/16"	FO3		535									1 11/16"					Series 42
	GJ3	959	1 15/16"	GP3			2596	2 5/16"		FP3	565	1 11/16"	Series 42														
	GK3	959	1 15/16"	GQ3			2658	2 5/16"		FQ3	605	1 11/16"										Series 42					
	GL3	996	1 15/16"	GR3	2721	2 5/16"	FR3	695		1 11/16"	Series 42																
	GM3	1004	1 15/16"	GS3	2846	2 5/16"	FS3	735		1 11/16"		Series 42															
	GN3	1054	1 15/16"	GT3	2908	2 5/16"	Series 42	26"	FK3	489				1 11/16"													
GO3	1069	1 15/16"	GU3	2958	2 5/16"	FL3			509	1 11/16"				Series 42													
GP3	1144	1 15/16"	GV3	3063	2 5/16"	FM3			555	1 11/16"					Series 42												
GQ3	1164	1 15/16"	GW3	3123	2 5/16"	FN3			574	1 11/16"						Series 42											
GR3	1190	1 15/16"	Series 43	16"	FO3	625			1 11/16"	FP3							655	1 11/16"	Series 42								
33"	GI3	1355			2 3/16"	FI3			302	1 3/16"							FQ3	715		1 11/16"	Series 42						
	GJ3	1355			2 3/16"	FJ3			302	1 3/16"			FR3				805	1 11/16"		Series 42							
	GK3	1382			2 3/16"	FK3			338	1 3/16"			FS3				845	1 11/16"				Series 42					
	GL3	1397			2 3/16"	FL3			358	1 3/16"	FT3		940				1 11/16"	Series 42									
	GM3	1454			2 3/16"	FM3			361	1 3/16"	Series 42	Series 42															
	GN3	1482			2 3/16"	FN3	380	1 3/16"	Series 42	Series 42																	
GO3	1514	2 3/16"			FO3	431	1 3/16"	Series 42					Series 42														
GP3	1544	2 3/16"			FP3	460	1 3/16"							Series 42	Series 42												
GQ3	1594	2 3/16"			Series 43	16"	Series 43									Series 43	Series 43						Series 43	Series 43			
GR3	1644	2 3/16"	Series 43	16"															Series 43						Series 43	Series 43	Series 43

*Net installation weights are for Arrangement 1. (Less motor & drive.)

Metric Conversion Table

FROM	TO	MULTIPLY BY
Inches (in.)	Millimeter (mm)	25.400
Feet (ft)	Meter (m)	0.3048
Velocity (ft./min)	Meter/Second (m/s)	0.00508
Volume Flow (cfm)	Cubic Meter/Second (m ³ s)	0.00047195
Pressure (in. w.g)	Pascal (N/m ²)	248.36
Density (lb./ft ³)	Kilogram /Cubic Meter (Kg/m ³)	16.018
Power (hp)	Watt (w)	745.70
Square Foot (ft ²)	Square Meter (m ²)	0.09290
Square Inch (in ²)	Square Meter (m ²)	0.0006451

Abrasive/Erosive Atmospheres

HartKoate is an abrasive erosive resistant coating developed by Hartzell for application in environments where abrasive/erosive conditions may exist. HartKoate helps prevent premature deterioration of equipment in environments where uncoated fans may fail.

Impact resistant HartKoate is applied to a 50-60 mil thickness suitable for temperatures to 200 F.

HartKoate is particularly appropriate for use when water mist and/or abrasive particles exist in the air stream.

Contact your Hartzell representative for further details concerning the application of HartKoate coating to fiberglass fans in corrosive atmospheres.

Installation Weights- Bearing/Shaft Sizes

Series 41

Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes	Size	Type	Net Wt. (lbs.)	Shaft Bearing Sizes																											
15"	GH3	526	1 7/16"	40"	GI3	1885	2 7/16"	19"	FI3	372	1 7/16"	30"	FL3	626	1 5/16"																											
	GI3	526	1 7/16"		GJ3	1885	2 7/16"		FJ3	372	1 7/16"		FM3	629	1 5/16"																											
	GJ3	529	1 7/16"		GK3	1912	2 7/16"		FK3	399	1 7/16"		FN3	649	1 5/16"																											
	GK3	529	1 7/16"		GL3	1932	2 7/16"		FL3	444	1 7/16"		FO3	709	1 5/16"																											
	GL3	549	1 7/16"		GM3	1972	2 7/16"		FM3	447	1 7/16"		FP3	739	1 5/16"																											
	GM3	554	1 7/16"		GN3	1987	2 7/16"		FN3	466	1 7/16"		FQ3	779	1 5/16"																											
22"	GH3	772	1 11/16"	49"	GO3	2047	2 7/16"	23"	FO3	517	1 7/16"	33"	FR3	869	1 5/16"																											
	GI3	772	1 11/16"		GP3	2077	2 7/16"		FP3	547	1 7/16"		FS3	909	1 5/16"																											
	GJ3	776	1 11/16"		GQ3	2127	2 7/16"		FQ3	587	1 7/16"		FT3	1004	1 5/16"																											
	GK3	776	1 11/16"		GR3	2177	2 7/16"		FR3	667	1 7/16"		*FU3	529	1 5/16"																											
	GL3	806	1 11/16"		GS3	2277	2 7/16"		26"	FK3	404		1 11/16"	Series 42	10"	FC3	63																									
	GM3	813	1 11/16"		GT3	2327	2 7/16"			FL3	431		1 11/16"					12"	FF3	78																						
GN3	854	1 11/16"	Series 43	16"	FH3	302	1 3/16"	FM3		496	1 11/16"	14"	FG3								96																					
GO3	865	1 11/16"						Series 41 (cont.)		GI3	1355											2 3/16"	FN3	516	1 11/16"																	
GP3	926	1 11/16"																					Series 41 (cont.)	GJ3	959	1 15/16"	FQ3	535	1 11/16"													
27"	GI3	954																									1 15/16"	Series 41 (cont.)	GK3	959	1 15/16"	FP3	565	1 11/16"								
									Series 41 (cont.)					GL3	996	1 15/16"	Series 41 (cont.)															GM3	1004	1 15/16"	FR3	945	1 5/16"					
																		Series 41 (cont.)	GN3	1054															1 15/16"	Series 41 (cont.)	GO3	1069	1 15/16"	FS3	985	1 5/16"
			Series 41 (cont.)	GP3	1144	1 15/16"	Series 41 (cont.)					GQ3	1164								1 15/16"																			FT3	1075	1 5/16"
								Series 41 (cont.)		GR3	1190											1 15/16"																		Series 41 (cont.)	GV3	3063
																							Series 41 (cont.)	GU3	2958	2 15/16"																
Series 41 (cont.)	Series 41 (cont.)	Series 41 (cont.)																									Series 41 (cont.)	Series 41 (cont.)	Series 41 (cont.)	Series 41 (cont.)	Series 41 (cont.)											

*Net installation weights are for Arrangement 1. (Less motor & drive.)

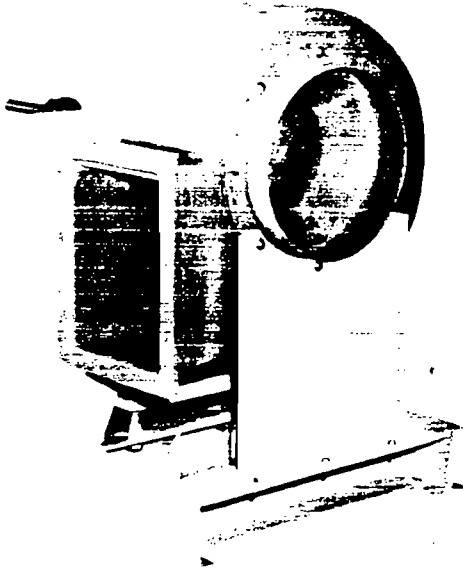
Metric Conversion Table

FROM	TO	MULTIPLY BY
Inches (in.)	Millimeter (mm)	25.400
Feet (ft)	Meter (m)	0.3048
Velocity (ft./min.)	Meter/Second (m/s)	0.00508
Volume Flow (cfm)	Cubic Meter/Second (m ³ /s)	0.00047195
Pressure (in. w.g.)	Pascal (N/m ²)	248.36
Density (lb./ft ³)	Kilogram/Cubic Meter (Kg/m ³)	16.018
Power (hp)	Watt (w)	745.70
Square Foot (ft ²)	Square Meter (m ²)	0.09290
Square Inch (in ²)	Square Meter (m ²)	0.0006451

Backward Curved Blower (Belt Drive)

Blowers available in SWSI only

The belt drive airfoil backward curved centrifugal blower offers non-overloading efficiency and economy in corrosive atmospheres at static pressures up to 12". The wheel and housing are constructed with a special corrosive resistant polyester resin having a Class I flame spread rate of 25 or less. No metal parts are exposed in the airstream. All internal hardware is 300 series stainless steel encapsulated with fiberglass.



Arrangement #10 Shown.



Series 41



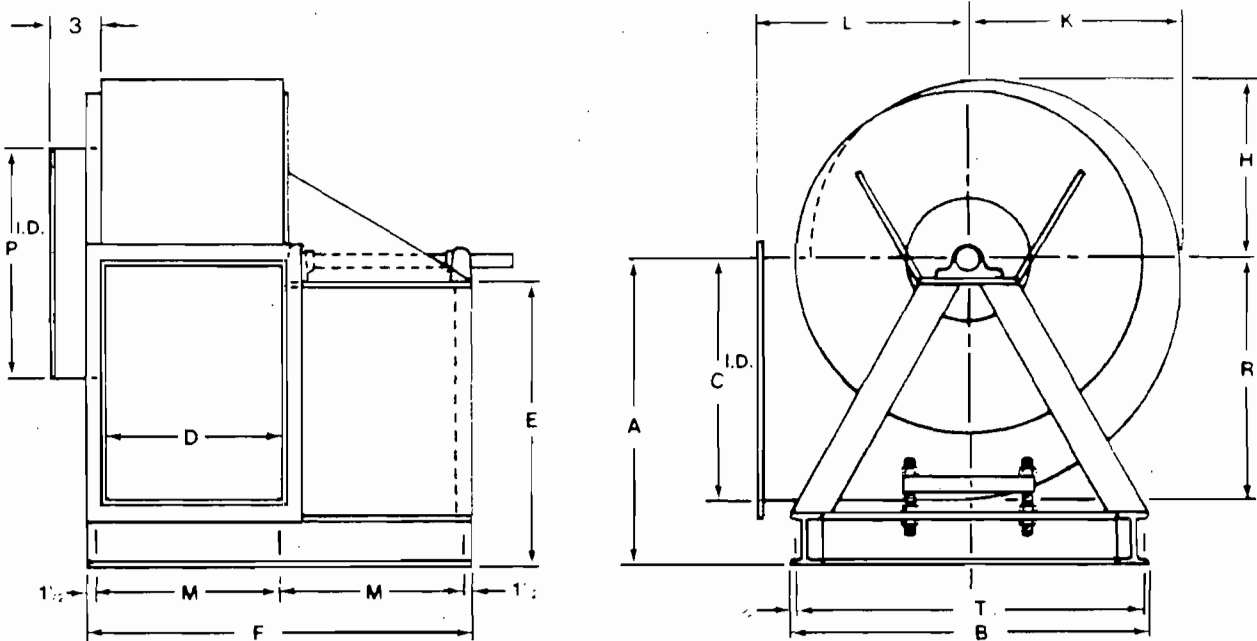
Features

- **Sizes** — 15", 22", 27", 33", 40", 49" wheel diameters.
- **Arrangements** — available in Arrangements #1, #9 or #10.
- **Rotation** — clockwise and counter clockwise rotation. Rotatable in field.
- **Discharges** — available discharges shown on page 9.
- **Packaged unit** — motor and drive mounted by factory.
- **Easy installation and maintenance** — motor, drive and bearings are readily accessible for ease in wiring, installation, adjustment and lubrication.
- **Wheel** — a true airfoil type of multi-piece, solid fiberglass construction bonded together with resin and fiberglass material. Airfoil backwardly inclined blades offer greater versatility for industrial applications. Wheel has non-overloading horsepower characteristics in that brake horsepower levels off at a point that prevents motor overload if system changes occur. Wheel Type G.
- **Motors** — open end drip proof are standard. Totally enclosed fan cooled and other special motors are available upon request.
- **Variable pitch drives** are standard on all units up to 10 HP.
- **Flanged outlets are standard.** Inlet flanges are optional. Drilling of flanges is optional. (Position of drilled holes must be specified by customer.)
- **All units are test run and electronically balanced** before shipment.
- **Heavy Duty Design** suitable for service up to and including Class III.
- **Bearings** — heavy duty, self-aligning, double row spherical roller type pillow block bearings are standard and are furnished with extended lubrication lines. Bearings have floating labyrinth seals. (See page 7 for Bearing/Shaft sizes.)
- **Shafts** are 304 stainless steel as standard. None! available at extra cost.
- **Bases** — heavy gauge hot rolled steel, epoxy coated.
- **Maximum Temperature:** 200° F.
- **Maximum tip speed:** 16,000 FPM
- **Accessories** —
See pages 22 and 23.

Principal Dimensions

Size	Wheel Dia.	A	B	C	D	E	F	H	K	L	M	P	R	T	Max. Motor Frame Size	
															ODP	TEFC
15	15 1/2	32 1/2	33 1/2	16 1/2	11 1/2	30 1/2	41	12 1/2	14 1/2	16 1/2	19	16	16 1/2	31 1/2	326T	286T
22	22 1/2	32 1/2	33 1/2	23 1/2	17 1/2	30 1/2	46	18 1/2	21 1/2	21 1/2	21	23	23 1/2	31 1/2	326T	286T
27	27 1/2	38 1/2	43 1/2	29 1/2	21 1/2	35 1/2	51	22 1/2	26 1/2	24	24	26	29 1/2	41 1/2	326T	286T
33	33 1/2	43 1/2	50 1/2	36 1/2	25 1/2	40 1/2	56	27 1/2	31 1/2	29 1/2	26	34 1/2	35 1/2	45 1/2	326T	286T
40	41 1/2	51 1/2	59 1/2	43 1/2	31 1/2	48 1/2	62	33 1/2	38 1/2	35 1/2	29 1/2	41 1/2	43 1/2	57 1/2	326T	286T
49	50 1/2	61 1/2	73 1/2	52 1/2	38 1/2	58 1/2	92	41 1/2	47 1/2	40 1/2	44 1/2	50 1/2	53 1/2	71 1/2	447T	447T

NOTES: ON 15 AND 22 SIZES WITH 254T FR. AND LARGER MOTORS. BASE DIMENSIONS MUST BE CERTIFIED BY THE FACTORY. DIMENSIONS AND SPECIFICATIONS ARE SUBJECT TO CHANGE. CERTIFIED PRINTS ARE AVAILABLE.

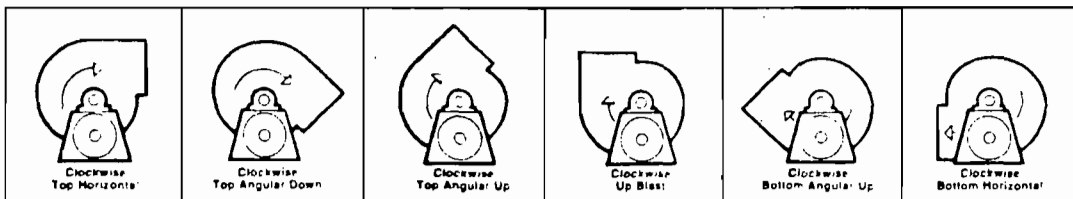


Material Specifications — Inches

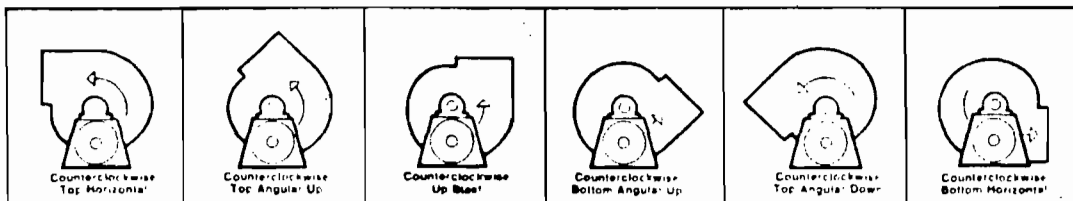
Size	HOUSING (Thickness)				(H.R.S.) FAN STAND			WHEEL (Thickness)		
	Scroll	Inlet Cone	Flanges		Back Plate	H-Beam	Channel	Blade	Back Plate	Outer Panel
			Inlet	Outlet						
15	5/16	5/16	3/16	5/16	1/2	6 x 4	4	1/2	1/2	1/2
22	5/16	7/16	1/2	5/16	1/2	6 x 4	4	1/2	5/8	5/8
27	1/2	1/2	5/16	1/2	1/2	6 x 4	4	5/8	3/4	3/4
33	1/2	5/8	5/8	1/2	1/2	6 x 4	4	3/4	7/8	7/8
40	5/8	3/2	7/16	5/8	1/2	6 x 4	4	7/16	1	1
49	5/8	15/16	5/16	1/2	1/2	6 x 4	4	1	1 1/8	1 3/8

Blower Discharges

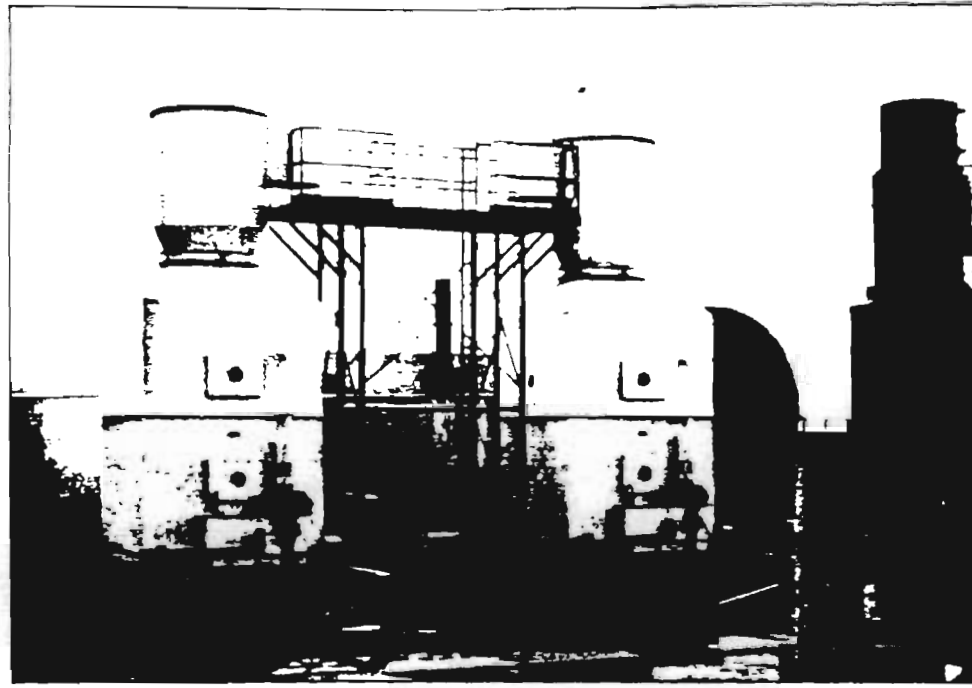
Clockwise



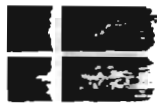
Counterclockwise



FIBERGLASS REINFORCED PLASTIC



INDUSTRIAL VENTILATION EQUIPMENT



BEVERLY PACIFIC CORPORATION

Equipment Division

...ING FABRICATOR...

... an "important function"

There are many factors involved in order to determine whether a company is a "qualified FRP fabricator". The main factors a person with purchasing responsibilities needs to recognize are the specific factors with which Beverly Pacific Corporation has had years of experience.

These factors deal with the handling and managing of the construction process itself — a few, of which, are as follows:

1. A "qualified fabricator" should be able to exhibit expertise in the basic principles of building corrosion-resistant laminates.
2. A "qualified fabricator" should have personnel familiar with resin compounding and curing, including variables such as catalysts, promoters, resin, reinforcement, time, temperature, humidity, rate of exotherm, mass of structure, etc.
3. A "qualified fabricator" should be able to demonstrate that shop personnel have necessary understanding and ability to produce good quality laminates consistently.
4. A "qualified fabricator" should apply proven procedures to assure adequate quality control of raw material and finished products.
5. A "qualified fabricator" should be able to use and produce engineering specifications, drawings and equipment designs and fabricate in accordance therewith.



BEVERLY PACIFIC CORPORATION

... a "qualified fabricator"

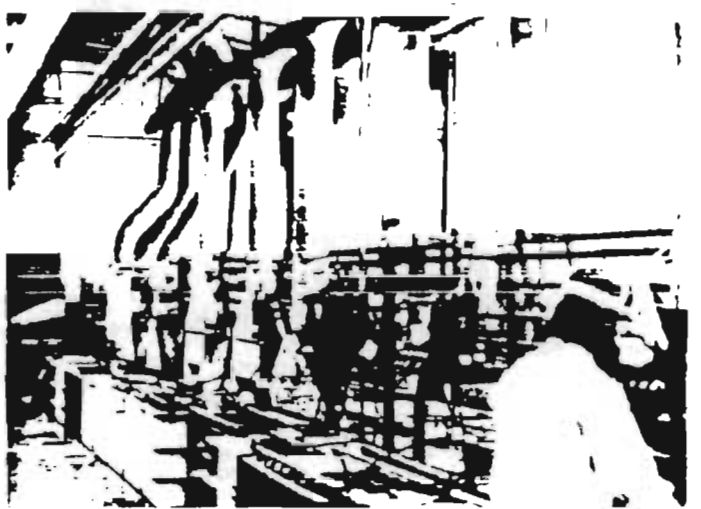
Beverly Pacific Corporation has served industry for over a quarter century. Our products, service, component equipment and complete engineered systems are located throughout the nation and around the world.

We have a "HIGHLY QUALIFIED TEAM" of engineers, production supervisors and experienced plant personnel, equipped with the latest production equipment, tools and proven methods of fabrication. This combination offers economical, dependable and efficient "ANSWERS" to your exhaust ventilation and corrosion control "PROBLEMS", and we want to serve you!



... a "necessity"

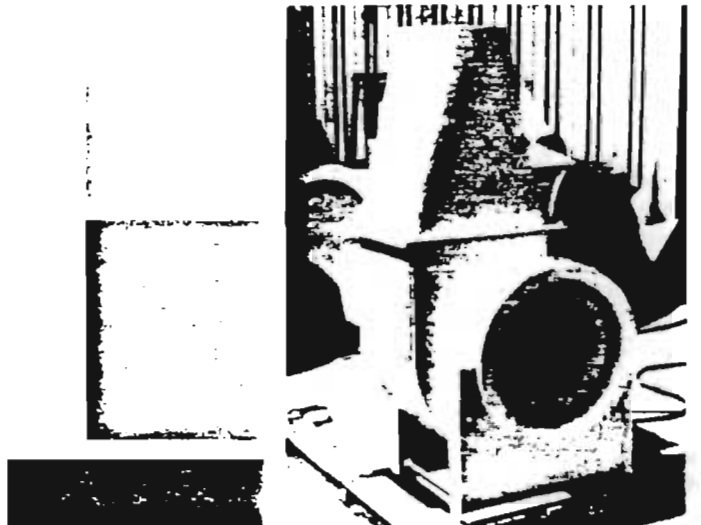
The "chemical resistance" of a *Fiberglass Reinforced Plastic (FRP)* product depends on the resin system and the method and type of reinforcement used in the construction. Polyester resin systems provide the best overall chemical resistance to the widest possible range of chemical environments. Superior performance of the resin is then assured by combining it with fiberglass and/or synthetic surfacing materials designed to accomplish both the "chemical resistance" and the "structural" requirements of the product.



POLYESTER RESIN SYSTEMS ...

... the "answer"

The continuing combined technical efforts of manufacturers such as *Beverly Pacific* and the producers of polyester resin have resulted in three (3) general **CHEMICAL-RESISTANT** polyester resin system groups: *Isophthalic, Bisphenol and Vinyl Ester polyesters*. Each of these polyester resin systems are available in **FIRE-RETARDANT** grades.



PRODUCTION CAPABILITIES ..

... the "dependable"

Beverly Pacific specializes in "**CORROSION CONTROL THRU ENGINEERING**", utilizing the unexcelled characteristics of *Fiberglass Reinforced Plastic (FRP)* materials in the design, fabrication and installation of industrial exhaust systems, component equipment and services requiring a high degree of corrosion resistance and exhaust emission contaminate removal.



The fabrication of standard or custom designed hoods, ducts, fittings, exhaust fans, fume scrubbers and washers, and exhaust stacks is one of the many services we offer to the metal plating, anodizing, chem-milling, petro-chemical and chemical processing industries.



1.0 SCOPE OF SPECIFICATIONS

1.1 This specification describes the materials of construction, procedures and physical properties that Beverly Pacific employs in the fabrication of Fiberglass Reinforced Plastic (FRP) equipment, utilizing hand lay-up and spray-up methods of construction, in compliance with the N.B.S. Voluntary Product Standard PS 15-69 for "Custom Contact-Molded Reinforced Polyester Chemical Resistant Process Equipment" issued by the U.S. Department of Commerce.

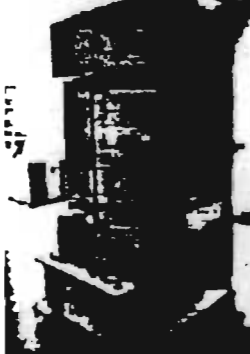
1.2 This standard is not intended to cover the selection of the exact resin of fiberglass reinforcement combination for any specific application. The specific resin selection is to be accomplished with the aid of the resin manufacturers' corrosion charts and/or recommendations made by their technical service departments.

2.0 GENERAL LAMINATE CONSTRUCTION

2.1 The FRP laminate shall consist of an inner surface, an interior layer, a structural layer and an exterior surface layer.

2.2 The compositions specified for the inner surface and the interior layer are intended to achieve optimum chemical resistance. This portion of the laminate is referred to as the "corrosion barrier".

2.3 The use of a premium grade chemical resistant resin throughout the laminate, or the use of a premium grade resin for the "corrosion barrier" in combination with an isophthalic resin for the structural layer, shall be agreed upon with the purchaser. This agreement shall be as specified on the request for quotation, our proposal, your acknowledgement and/or the drawings submitted for approval.



2.4 The laminate surface shall have a Barcol hardness of at least 90 percent of the resin manufacturers' minimum specification.

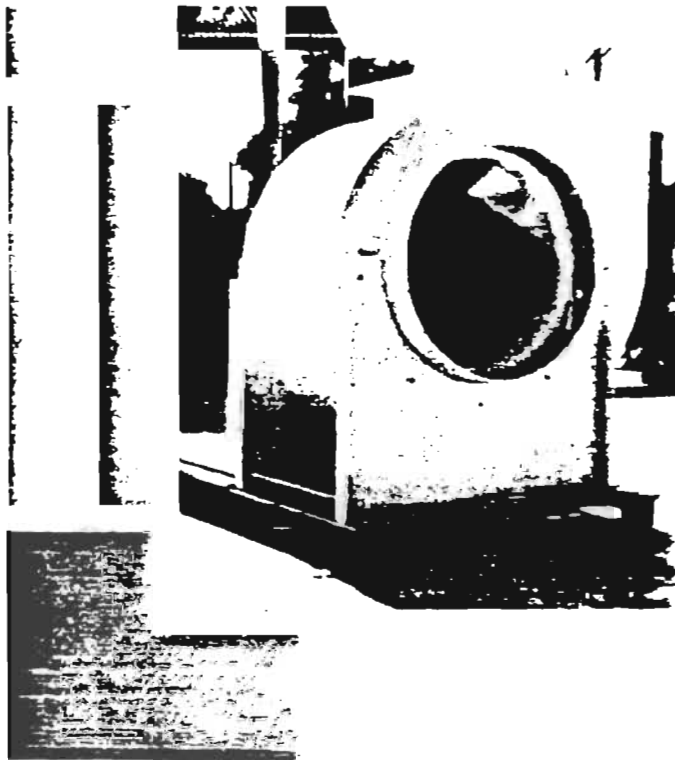
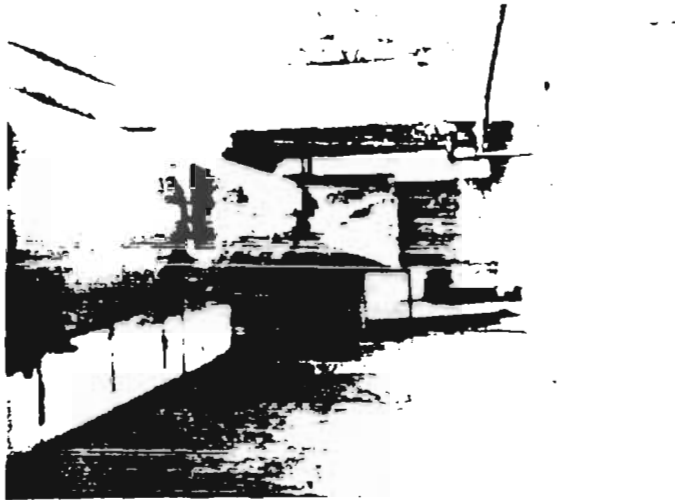
3.0 HAND LAY-UP AND SPRAY-UP LAMINATE CONSTRUCTION

3.1 **INNER SURFACE:** The inner surface resin shall be between 0.010 and 0.020 inches thick and be reinforced with glass or synthetic surfacing veil, depending on the chemical environment. This surface shall be free of cracks and crazing, having an average of not more than two (2) pits per square foot, providing these pits are less than 1/8" in diameter and not more than 1/32" deep. All pits must be covered with sufficient resin to prevent exposure of inner surface reinforcement.

3.2 **INTERIOR LAYER:** A minimum of 0.100 inch of laminate next to the inner surface shall be reinforced with not less than twenty (20) percent nor more than thirty (30) percent by weight of noncontinuous glass (chopped strand) fibers, having fiber lengths of 0.5 to 2.0 inches.

3.3 **STRUCTURAL LAYER:** The structural layer of the laminate shall provide the additional strength necessary to meet the tensile and flexural requirements. Where separate layers such as mat or woven roving are used, all layers shall be lapped a minimum of one (1) inch. Laps shall be staggered as much as possible and if woven roving is used, alternate layers of chopped strand glass shall be used.

3.4 **EXTERIOR LAYER:** The exterior surface shall be relatively smooth with no exposed fibers or sharp projections. Hand-work finish is acceptable; however, a sufficient amount of resin shall be present to prevent fiber exposure. The final laminate shall be coated with a resin containing a paraffin surfacing agent to achieve a fully cured exterior surface.



4.0 MATERIALS OF CONSTRUCTION

4.1 **RESIN:** The resin used shall be of commercial grade and shall have had previous service history acceptable for the specific environment. Environment includes the nature of the chemical, the concentration and the service temperature.

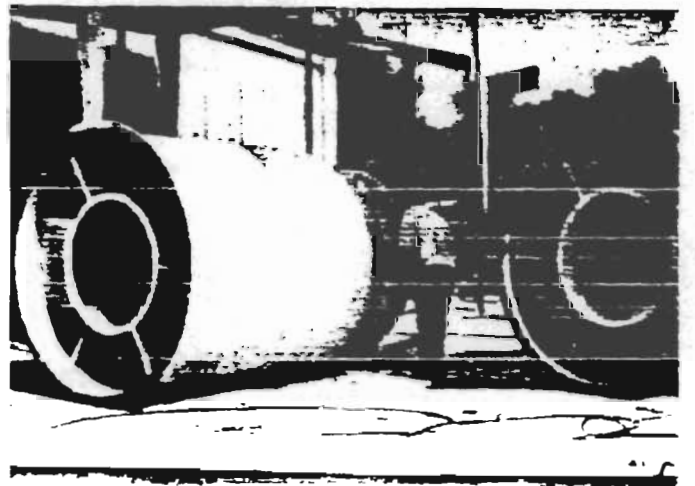
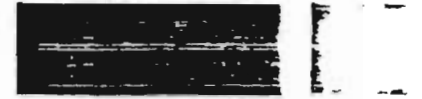
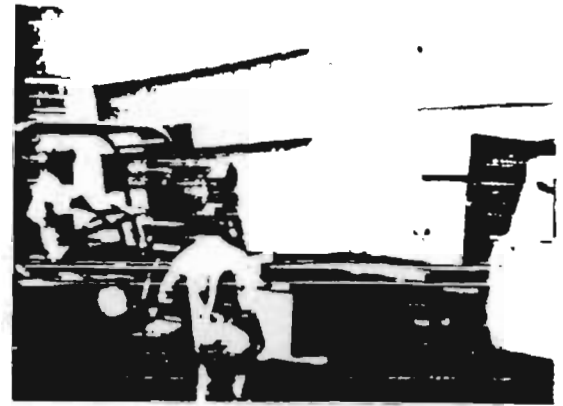
4.2 **FILLERS AND PIGMENTS:** The resins used shall not contain fillers or pigments except when required as follows:

- a. Up to 5% thixotropic agent which will not interfere with visual inspection may be added for viscosity control.
- b. Antimony compounds or other fire-retardant agents may be added to improve fire resistance at the request of the purchaser.
- c. Ultraviolet absorbers and/or pigments shall be added to final resin coating on the exterior surface to improve weather resistance.
- d. To insure a tack-free, fully cured, corrosion-resistant surface, up to 0.6 percent of paraffin wax, by weight, must be added to the final resin coat.

4.3 **SURFACE REINFORCEMENT:** The glass fiber reinforcement used on surfaces exposed to chemical environment shall be Type "C" monofilament surfacing veil, having a thickness of 10 to 20 mils, a silane finish and a styrene soluble binder.

4.4 **OPTIONAL SURFACE REINFORCEMENT:** Where the chemical environment would attack glass fibers, synthetic surfacing materials such as acrylic, polyester, asbestos or other organic fiber may be used, as agreed upon by Beverly Pacific and the purchaser.

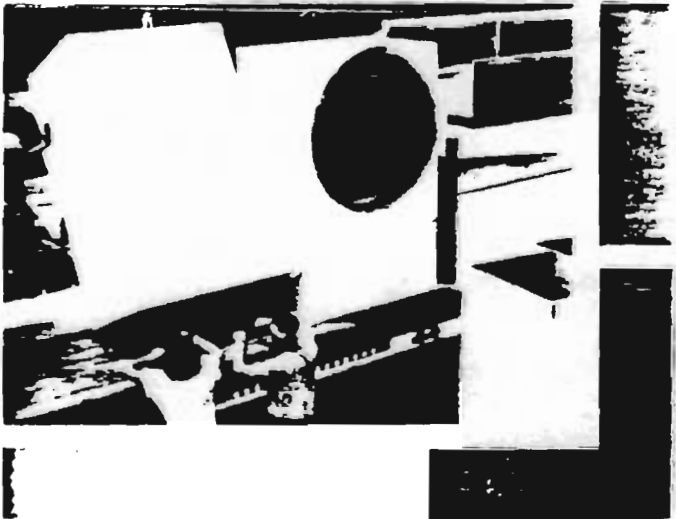
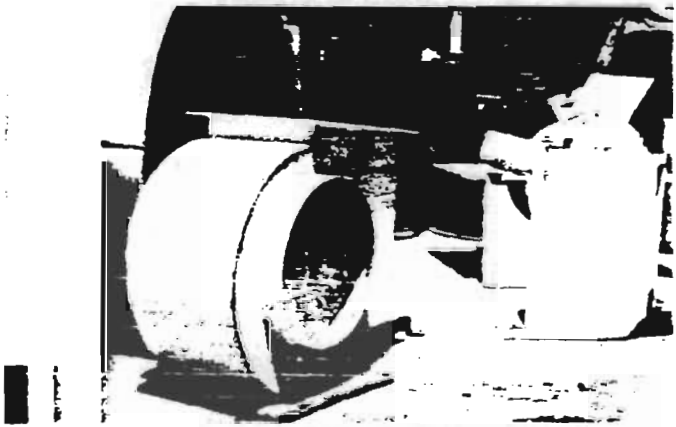
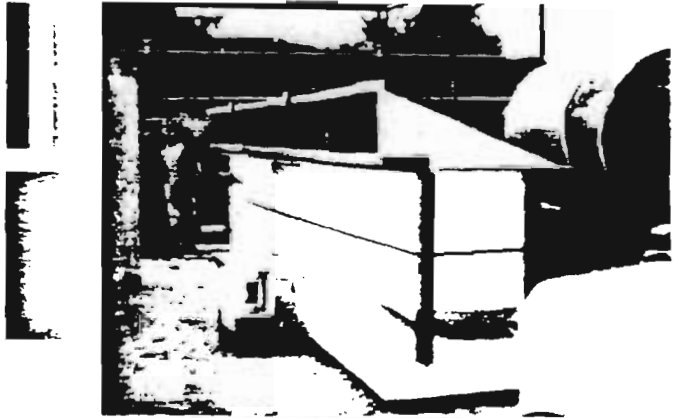
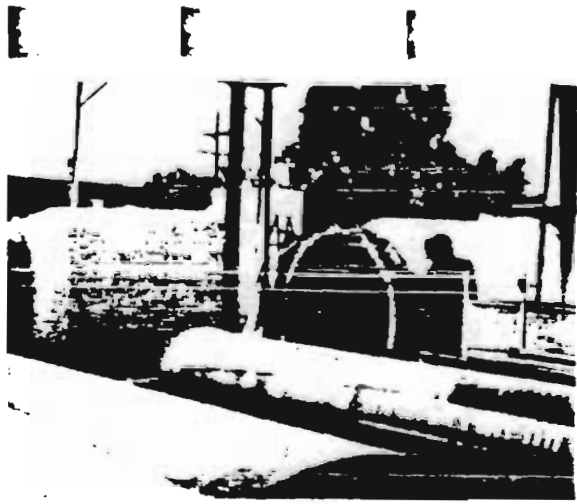
4.5 **CHOPPED STRAND MAT REINFORCEMENT:** Chopped strand glass mat used for reinforcement shall be Type "E" glass, 1 1/2 oz. per square foot, having a silane finish and a soluble binder.



WOVEN ROVING REINFORCEMENT:
Woven roving used for additional structural reinforcement shall be 60 end, Type "E" glass, having a silane finish

GUN ROVING REINFORCEMENT:
Continuous gun roving used in chopper gun spray-up shall be 60 end, Type "E" glass having a silane or chrome-silane finish

Note: As stated in Paragraph 1.1 of these specifications, Beverly Pacific's standard methods of construction comply with PS15-69; however, as evidence of our industry leadership, up-graded modifications of this quality standard have been utilized by Beverly Pacific for years. At the time of this printing, it is our understanding that such up-graded modifications are to be standardized by proposed ASTM Product Standards for the corrosion-resistant equipment manufacturing industry.



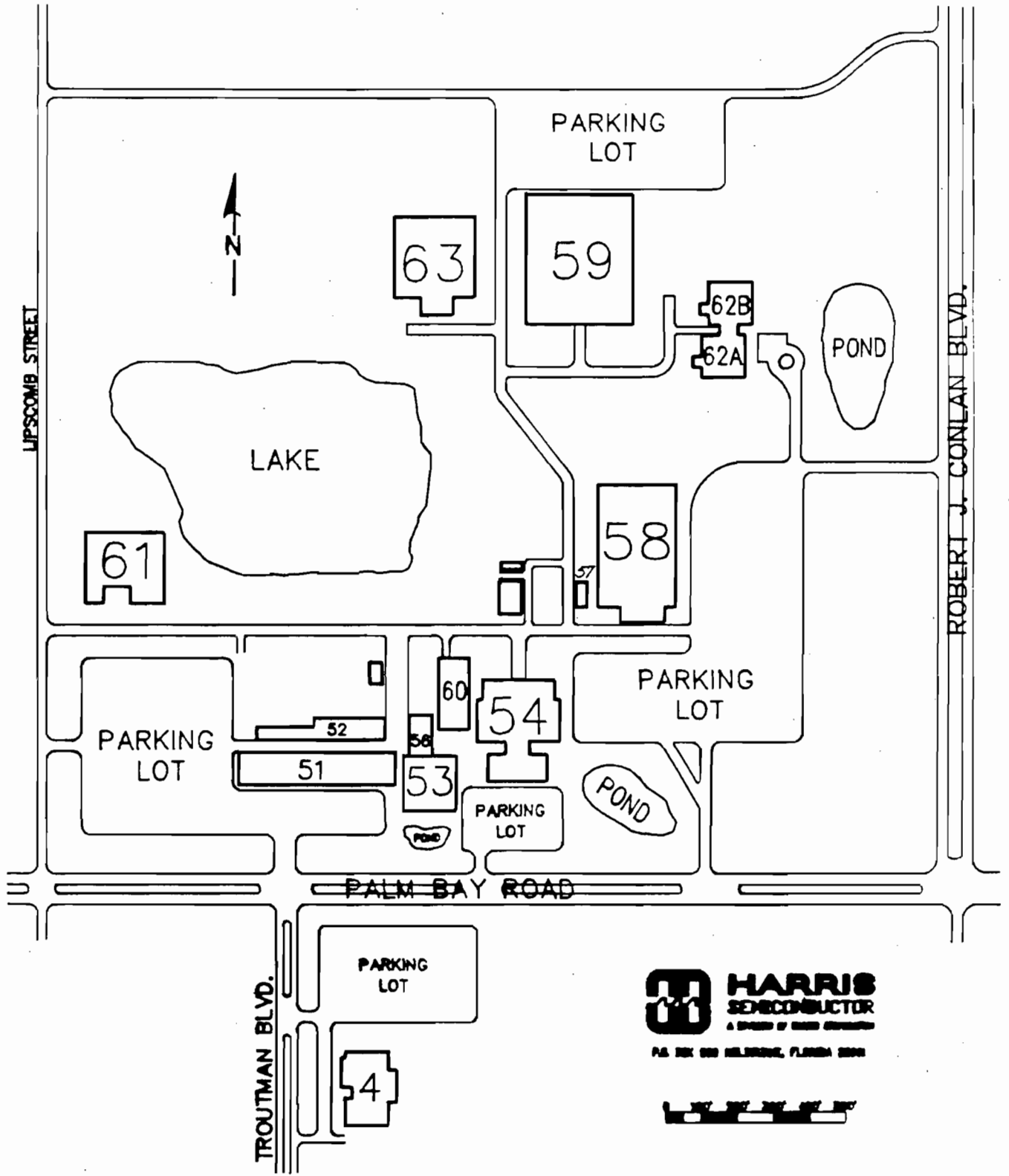
HARRIS SEMICONDUCTOR

B-54 Air Permit

Consolidation

ATTACHMENT E

Maps



LIPSCOMB STREET



ROBERT J. CONLAN BLVD.

61

63

59

62B

62A

POND

LAKE

58

PARKING LOT

52

60

54

PARKING LOT

51

56

53

PARKING LOT

POND

PALM BAY ROAD

TROUTMAN BLVD.

PARKING LOT

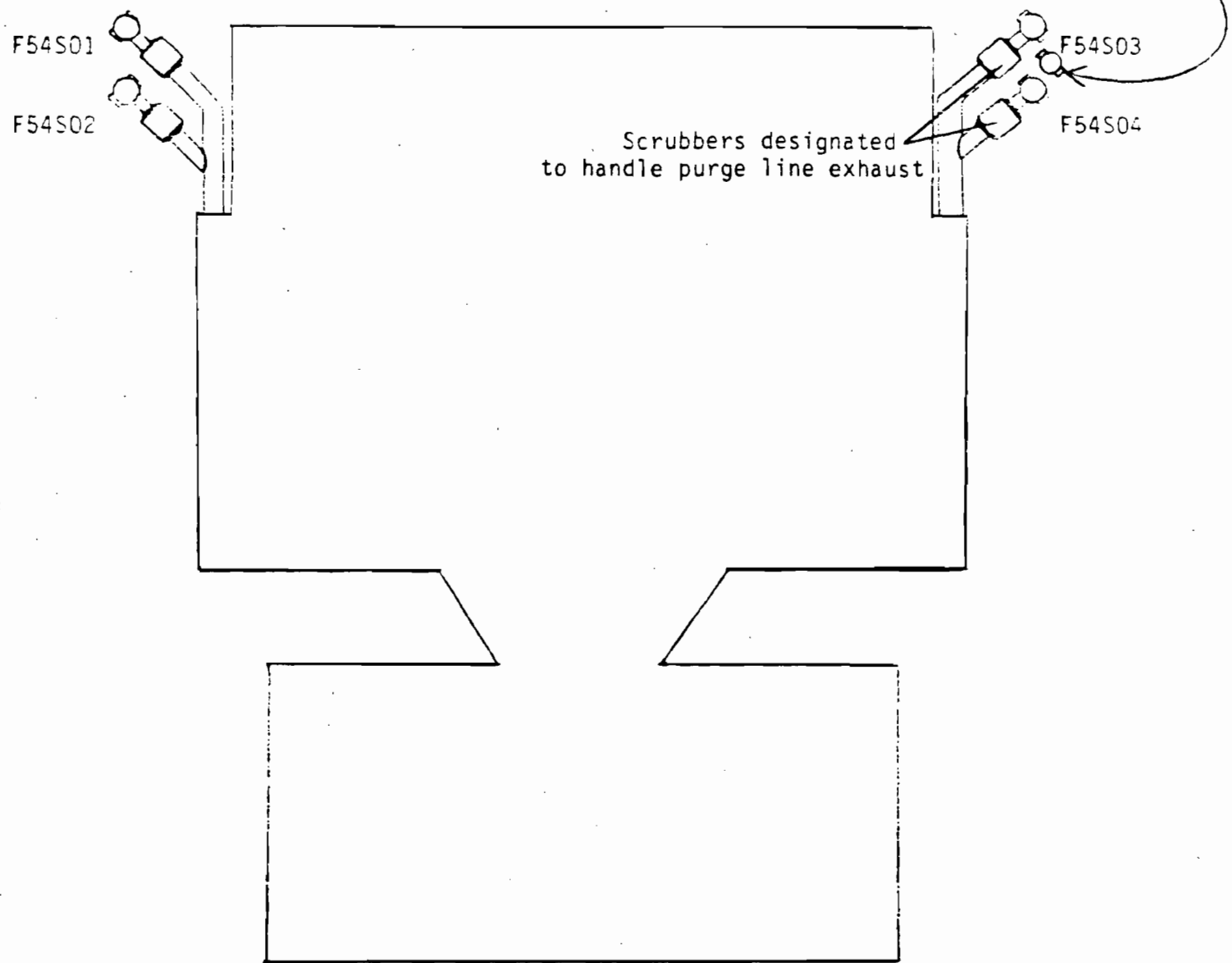
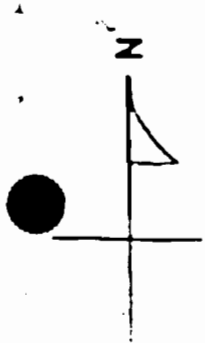
4









P.O. BOX 999 MELBOURNE, FLORIDA 32901



HARRIS SEMICONDUCTOR
 SCRUBBER LOCATIONS
 BUILDING 54



LEGEND

-  - Horizontal Scrubber
-  - Vertical Scrubber
-  - Exhaust Stack
-  - Exhaust Fan
-  - Stack mounted on fan
-  - Epitaxial Scrubber

STATE OF FLORIDA

DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKEL
SECRETARY

November 5, 1985

CERTIFIED MAIL-RETURN RECEIPT REQUESTED

Mr. J. R. Kolanek
Manager, Environmental Services
Harris Semiconductor
Post Office Box 883
Melbourne, Florida 32901

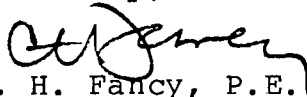
Dear Mr. Kolanek:

Attached is one copy of the Technical Evaluation and Preliminary Determination, and proposed permits to install hood-type working stations and storage stations with associated scrubbers at your existing facility in Melbourne, Brevard County, Florida.

Before final action can be taken on your draft permits, you are required by Florida Administrative Code Rule 17-103.150 to publish the attached Notice of Proposed Agency Action in the legal advertising section of a newspaper of general circulation in Brevard County no later than fourteen days after receipt of this letter. The department must be provided with proof of publication within seven days of the date the notice is published. Failure to publish the notice may be grounds for denial of the permits.

Please submit, in writing, any comments which you wish to have considered concerning the department's proposed action to Mr. Bill Thomas of the Bureau of Air Quality Management.

Sincerely,


C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management

CHF/pa

Attachments

cc: Tom Sawicki

State of Florida
Department of Environmental Regulation
Notice of Proposed Agency Action
on Permit Applications

The Department of Environmental Regulation gives notice of its intent to issue permits to Harris Semiconductor for the installation of hood-type working stations and storage stations with associated scrubbers at their existing facility in Melbourne, Brevard County, Florida. A determination of best available control technology (BACT) was not required.

Persons whose substantial interests are affected by the Department's proposed permitting decision may petition for an administrative proceeding (hearing) in accordance with Section 120.57, Florida Statutes. The petition must conform to the requirements of Chapters 17-103 and 28-5, Florida Administrative Code, and must be filed (received) in the Office of General Counsel of the Department at 2600 Blair Stone Road, Twin Towers Office Building, Tallahassee, Florida 32301, within fourteen (14) days of publication of this notice. Failure to file a request for hearing within this time period constitutes a waiver of any right such person may have to request an administrative determination (hearing) under Section 120.57, Florida Statutes.

If a petition is filed, the administrative hearing process is designed to formulate agency action. Accordingly, the Department's final action may be different from the proposed agency action. Therefore, persons who may not wish to file a petition may wish to intervene in the proceeding. A petition for intervention must be filed pursuant to Model Rule 28-5.207, Florida Administrative Code, at least five (5) days before the final hearing and be filed with the hearing officer if one has been assigned at the Division of Administrative Hearings, Department of Administration, 2009, Apalachee Parkway, Tallahassee, Florida 32301. If no hearing officer has been assigned, the petition is to be filed with the department's Office of General Counsel, 2600 Blair Stone Road, Tallahassee, Florida 32301. Failure to petition to intervene within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, Florida Statutes.

The application is available for public inspection during normal business hours, 8:00 a.m. to 5:00 p.m., Monday through Friday, except legal holidays, at:

Dept. of Environmental Regulation
St. Johns River District
3319 Maguire Blvd., Suite 232
Orlando, Florida 32803

Dept. of Environmental Regulation
Bureau of Air Quality Management
2600 Blair Stone Road
Tallahassee, Florida 32301

Any person may send written comments on the proposed action to Mr. Bill Thomas at the department's Tallahassee address. All comments mailed within 30 days of the publication of this notice will be considered in the department's final determination.

BEFORE THE STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

In the Matter of)	DER File No.	AC 05-104511
Application for Permits by:)		AC 05-104512
)		AC 05-104513
Harris Semiconductor)		AC 05-104514
Post Office Box 883)		AC 05-104515
Melbourne, Florida 32901)		AC 05-104516
)		AC 05-104518
)		AC 05-104519
)		AC 05-104521
)		AC 05-104522
)		AC 05-104523
)		AC 05-104524
)		AC 05-104525
)		AC 05-104527

INTENT TO ISSUE

The Department of Environmental Regulation hereby gives notice of its Intent to Issue, and proposed order of issuance for, a permit pursuant to Chapter 403, Florida Statutes, for the proposed project as detailed in the application specified above. The Department is issuing this Intent to Issue for the reasons stated in the attached Technical Evaluation and Preliminary Determination.

The applicant, Harris Semiconductor, applied on May 22, 1985 to DER for permits to construct hood-type working stations and storage stations with associated scrubbers at the applicant's facility in Melbourne, Brevard County, Florida.

The Department has permitting jurisdiction under Chapter 403, Florida Statutes and Florida Administrative Code Rules 17-2 and 17-4. The project is not exempt from permitting procedures. The applicant was officially notified by the Department that air construction permits were required for the proposed work.

This intent to issue shall be placed before the Secretary for final action unless an appropriate petition for a hearing pursuant to the provisions of Section 120.57, Florida Statutes, is filed within fourteen (14) days from receipt of this letter or publication of the public notice (copy attached) required pursuant to Rule 17-103.150, Florida Administrative Code, whichever occurs first. The petition must comply with the requirements of Section 17-103.155 and Rule 28-5.201, Florida Administrative Code (copy attached) and be filed pursuant to Rule 17-103.155(1) in the Office of General Counsel of the Department of Environmental Regulation at 2600 Blair Stone Road, Tallahassee, Florida 32301.

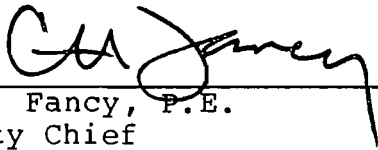
Petitions which are not filed in accordance with the above provisions are subject to dismissal by the Department. In the event a formal hearing is conducted pursuant to Section 120.57(1), all parties shall have an opportunity to respond, to present evidence and argument on all issues involved, to conduct cross-examination of witnesses and submit rebuttal evidence, to submit proposed findings of facts and orders, to file exceptions to any order or hearing officer's recommended order, and to be represented by counsel. If an informal hearing is requested, the agency, in accordance with its rules of procedure, will provide affected persons or parties or their counsel an opportunity, at a convenient time and place, to present to the agency or hearing officer, written or oral evidence in opposition to the agency's action or refusal to act, or a written statement challenging the grounds upon which the agency has chosen to justify its action or inaction, pursuant to Section 120.57(2), Florida Statutes.

If a petition is filed, the administrative hearing process is designed to formulate agency action. Accordingly, the Department's final action may be different from the proposed

agency action. Therefore, persons who may not wish to file a petition, may wish to intervene in the proceeding. A petition for intervention must be filed pursuant to Model Rule 28-5.207 at least five (5) days before the final hearing and be filed with the hearing officer if one has been assigned at the Division of Administrative Hearings, 2009 Apalachee Parkway, Tallahassee, Florida 32301. If no hearing officer has been assigned, the petition is to be filed with the Department's Office of General Counsel, 2600 Blair Stone Road, Tallahassee, Florida 32301. Failure to petition to intervene within the allowed time frame constitutes a waiver of any right such person has to request a hearing under Section 120.57, Florida Statutes.

Executed the 5 day of NOV, 1985, in Tallahassee, Florida.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION




C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management

Copies furnished to:

Mr. J. R. Kolanek, Harris Semiconductor
Tom Sawicki, DER St. Johns River District

CERTIFICATION

This is to certify that the foregoing Intent to Issue and all copies were mailed before the close of business on 5 NOV, 1985.



C. H. Fancy, P.E.
Deputy Chief
Bureau of Air Quality
Management
2600 Blair Stone Road
Tallahassee, Florida 32301

FILING AND ACKNOWLEDGEMENT
FILED, on this date, pursuant to
§120.52(9), Florida Statutes, with
the designated Department Clerk,
receipt of which is hereby acknow-
ledged.

Patricia G. Adams Nov. 5, 1985
Clerk Date

RULES OF THE ADMINISTRATIVE COMMISSION
MODEL RULES OF PROCEDURE
CHAPTER 28-5
DECISIONS DETERMINING SUBSTANTIAL INTERESTS

28-5.15 Requests for Formal and Informal Proceedings

- (1) Requests for proceedings shall be made by petition to the agency involved. Each petition shall be printed typewritten or otherwise duplicated in legible form on white paper of standard legal size. Unless printed, the impression shall be on one side of the paper only and lines shall be double spaced and indented.
- (2) All petitions filed under these rules should contain:
 - (a) The name and address of each agency affected and each agency's file or identification number, if known;
 - (b) The name and address of the petitioner or petitioners;
 - (c) All disputed issues of material fact. If there are none, the petition must so indicate;
 - (d) A concise statement of the ultimate facts alleged, and the rules, regulations and constitutional provisions which entitle the petitioner to relief;
 - (e) A statement summarizing any informal action taken to resolve the issues, and the results of that action;
 - (f) A demand for the relief to which the petitioner deems himself entitled; and
 - (g) Such other information which the petitioner contends is material.

Technical Evaluation
and
Preliminary Determination

Semiconductor Production Process
Harris Semiconductor
Brevard County
Melbourne, Florida

Application Numbers:

AC 05-104511
104512
104513
104514
104515
104516
104518
104519
104521
104522
104523
104524
104525
104527

Department of Environmental Regulation
Bureau of Air Quality Management
Central Air Permitting Section

November 5, 1985

I. Project Description

A. Applicant

Harris Semiconductor
P. O. Box 833
Melbourne, Florida 32901

B. Project Description and Location

The applicant intends to install hood type working and storage stations for the manufacture of semiconductors. The working and storage stations will be installed in existing buildings (Bldgs. 4 North, 4 South, 55, 57, 58, 58 Annex, 59, 62, and 63). Gases and vapors of volatile organic compounds (VOC), solvents, and acids will be vented to associated scrubber systems.

The applicant also requests construction permits (6) for operations which construction permits were issued previously and operating permits were never obtained.

The existing facility is located on Palm Bay Road in Palm Bay City, Brevard County, Florida. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

C. Process and Controls

The manufacture of the semiconductors involves the immersing of the material in various acids, VOC, and solvents. Acid, VOC, and solvent vapors are released into the air from both surface evaporation and material drying. Various gases contained in bottles are also used in the production of the semiconductors.

The released gases and acid, VOC and solvent vapors will be captured by a hood system and vented to a scrubber system. A material balance verification system will be employed at this facility to account for the VOC/solvent emissions released into the atmosphere. A program of sampling and analyses will be instituted to maintain proper scrubber effluents.

II. Rule Applicability

The proposed project is subject to the preconstruction review under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code (FAC) Rules 17-2 and 17-4.

The application package was deemed complete on August 27, 1985.

The proposed project is located in an area designated attainment for all pollutants. Therefore, review shall be in

accordance with FAC Rule 17-2.500, Prevention of Significant Deterioration (PSD).

Based on 1984 emissions inventory, the existing facility's potential VOC/solvent emissions are 11.95 TPY (91.43 TPY uncontrolled), which is a minor facility pursuant to FAC Rule 17-2.100(115). The proposed increase in VOC/solvent potential emissions is 0.39 TPY (5.13 TPY uncontrolled), which will be a minor modification to a minor facility and exempt from new source review requirements pursuant to FAC Rule 17-2.500, PSD. Therefore, the potential pollutant emissions will be reviewed in accordance with FAC Rule 17-2.520, Sources Not Subject to PSD or Nonattainment Requirements.

Since there is no specific emission limiting standard contained in FAC Rule 17-2.600 nor is there any standards of performance for new stationary sources contained in FAC Rule 17-2.660, the modification will be permitted in accordance with FAC Rule 17-2.620, General Pollutant Emission Limiting Standards.

In FAC Rule 17-2.620(1)(a), no person shall store, pump, handle, process, load, unload or use in any process or installation volatile organic compounds or organic solvents without applying known and existing vapor emission control devices or systems deemed necessary and ordered by the Department. FAC Rule 17-2.620(2) states that no person shall cause, suffer, allow or permit the discharge of air pollutants which cause or contribute to an objectionable odor. Objectionable odor is defined as any odor present in the outdoor atmosphere, which by itself or in combination with other odors, is or may be harmful or injurious to human health or welfare, which unreasonably interferes with the comfortable use and enjoyment of life or property, or which creates a nuisance according to FAC Rule 17-2.100(108).

III. Summary of Emissions

A. Emission Limitations

The regulated pollutant emissions from this modification to the existing facility are VOC/solvents in accordance with FAC Rule 17-2.620.

Specific acids and gases are also being used during the manufacturing operations. There are no specific emission limiting standards for these specific chemicals and gases. However, their emissions will be minimized with scrubbers.

Table 1 reflects the allowable VOC/solvent emissions from Buildings 4 North, 4 South, 57, 58, 58 Annex, 59, 61, 62, and 63.

Table 1

Building	Maximum VOC/Solvent Allowable Emissions	
	lbs/yr	TPY
4 North	4.4	0.002
4 South	79.7	0.040
57	1.1	0.001
58	353.1	0.177
58 Annex	4.2	0.002
59	3.8	0.002
61	199.0	0.099
62	113.4	0.057
63	26.6	0.013
Totals:	785.3	0.393

The permitted emissions are in compliance with all requirements of FAC Rule 17-2.

B. Air Quality Impacts

From the technical review of the applications and amendments, the bureau has determined that the modification at the existing facility will not cause a violation of Florida's ambient air quality standards.

IV. Conclusion

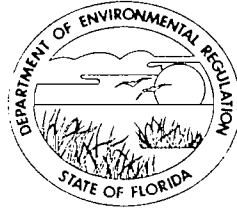
The maximum allowable VOC/solvent emissions from this modification to the existing facility should not cause any violation of Florida's ambient air quality standards. Even though there are no emissions standards for the acids and gases used, the applicant will be installing scrubber systems to reduce emissions and prevent odors from entering the outside atmosphere.

The use of a material balance verification system for the VOC/solvents will account for the emissions lost to the atmosphere from the facility. A program of sampling and analyses employed by the applicant to maintain the scrubber systems should be adequate to keep emissions at their minimum and objectionable odors from escaping.

AC 05-104511

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104511
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 63 Acid Vapor
Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors in Building 63. A 50,000 dscfm fume scrubber manufactured by Beverly Pacific is installed to control acid vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5 and 6, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104511
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.
2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.
3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.
4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.
5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104511
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104511
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104511
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The potential acid vapor emissions from the work stations and scrubber system is 4.4 pounds per year.
2. The acid vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 24 hours per day, 264 days per year, for a total of 6,336 hours per year.
4. A meter to measure the pressure drop shall be installed on the scrubber system.
5. Objectionable odors shall not be allowed off plant property.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104511
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

6. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)

To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)

If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

Issued this ____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

____ pages attached.

AC 05-104512

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104512
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 63 VOC/Solvent
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors in Building 63. A 10,000 dscfm fume scrubber manufactured by Beverly Pacific is installed to control VOC/solvent vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104512
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.
2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.
3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.
4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.
5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104512
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104512
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104512
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

- 1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 26.6 pounds per year.
- 2. The VOC/solvent vapor exhaust scrubber must be on during the working hours.
- 3. The maximum operating hours allowed shall be 24 hours per day, 264 days per year, for a total of 6,336 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104512
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.

5. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.

6. A meter to measure the pressure drop shall be installed on the scrubber system.

7. Objectionable odors shall not be allowed off plant property.

8. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.

9. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)

To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)

If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104512
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104513

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104513
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 62 VOC/Solvent
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors in Building 62. A 12,000 dscfm fume scrubber manufactured by Beverly Pacific is installed to control VOC/solvent vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104513
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104513
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104513
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104513
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 113.4 pounds per year.
2. The VOC/solvent vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104513
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
5. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
6. A meter to measure the pressure drop shall be installed on the scrubber system.
7. Objectionable odors shall not be allowed off plant property.
8. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
9. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104513
Expiration Date: June 30, 1986

SPECIFIC CONDITION:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104514

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104514
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 62 Acid Vapor
Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors in Building 62. A 24,000 dscfm fume scrubber manufactured by Beverly Pacific is installed to control acid vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5 and 6, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-04514
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.
2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.
3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.
4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.
5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104514
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104514
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104514
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The potential acid vapor emissions from the work stations and scrubber system is 3.6 pounds per year.
2. The acid vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.
4. A meter to measure the pressure drop shall be installed on the scrubber system.
5. Objectionable odors shall not be allowed off plant property.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104514
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

6. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)

To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)

If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104515

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104515
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 59 VOC/Solvent
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors in Building 59. A 20,000 dscfm fume scrubber manufactured by Beverly Pacific is installed to control VOC/solvent vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104515
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104515
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104515
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104515
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 3.8 pounds per year.
2. The VOC/solvent vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104515
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
5. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
6. A meter to measure the pressure drop shall be installed on the scrubber system.
7. Objectionable odors shall not be allowed off plant property.
8. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
9. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITEE:
Harris Semiconductor

Permit Number: AC 05-104515
Expiration Number: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104516

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104516
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 59 Acid Vapor
Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors in Building 59. A 40,000 dscfm fume scrubber manufactured by Beverly Pacific is installed to control acid vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5 and 6, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104516
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104516
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104516
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104516
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The potential acid vapor emissions from the work stations and scrubber system is 16.7 pounds per year.
2. The acid vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.
4. A meter to measure the pressure drop shall be installed on the scrubber system.
5. Objectionable odors shall not be allowed off plant property.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104516
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

6. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)

To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)

If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

Issued this _____ day of _____,
19__.

**STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION**

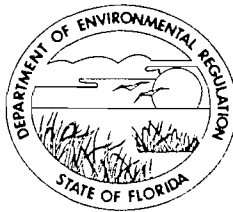
VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104518

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104518
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 61 Acid Vapor
Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the preparation of working concentrations of acids in Building 61. A 10,000 dscfm fume scrubber manufactured by Duall is installed to control acid vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5 and 6, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104518
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104518
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104518
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104518
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The potential acid vapor emissions from the work stations and scrubber system is 57.0 pounds per year.
2. The acid vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 24 hours per day, 264 days per year, for a total of 6,336 hours per year.
4. A meter to measure the pressure drop shall be installed on the scrubber system.
5. Objectionable odors shall not be allowed off plant property.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104518
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

6. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)

To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)

If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

Issued this _____ day of _____,
19__.

**STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION**

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104519

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104519
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 61 VOC/Solvent
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the construction of hood type work stations for the preparation of working mixtures of VOC/solvents in Building 61. A 1,700 dscfm fume scrubber manufactured by Harrison will be installed to control VOC/solvent vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

Construction shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104519
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104519
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104519
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104519
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 199.0 pounds per year.
2. The VOC/solvent vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104519
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
5. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
6. A meter to measure the pressure drop shall be installed on the scrubber system.
7. Objectionable odors shall not be allowed off plant property.
8. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
9. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104519
Expiration Date: June 30, 1985

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

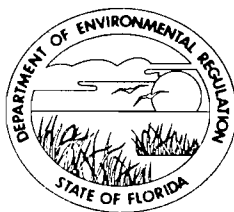
VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104521

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104521
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 58 Chemical
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the packaging and testing of semiconductors Building 58. A 12,500 dscfm fume scrubber manufactured by Tri-Mer is installed to control VOC/solvent/acid vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104521
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.
2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.
3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.
4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.
5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104521
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104521
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104521
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
- the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 353.1 pounds per year.
2. The potential acid vapor emissions from the work stations and scrubber system is 0.4 pounds per year.
3. The VOC/solvent/acid vapor exhaust scrubber must be on during the working hours.
4. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104521
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

5. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
6. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
7. A meter to measure the pressure drop shall be installed on the scrubber system.
8. Objectionable odors shall not be allowed off plant property.
9. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
10. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104521
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

**STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION**

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104522

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104522
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 57 Chemical
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the packaging and plating of semiconductors Building 57. A 13,500 dscfm fume scrubber manufactured by Tri-Mer is installed to control VOC/solvent/acid vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104522
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.
2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.
3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.
4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.
5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104522
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104522
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104522
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
- the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 1.1 pounds per year.
2. The potential acid vapor emissions from the work stations and scrubber system is 1.9 pounds per year.
3. The VOC/solvent/acid vapor exhaust scrubber must be on during the working hours.
4. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104522
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

5. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
6. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
7. A meter to measure the pressure drop shall be installed on the scrubber system.
8. Objectionable odors shall not be allowed off plant property.
9. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
10. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104522
Expiration: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104523

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104523
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 55 Chemical
Vapor Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of the collection area with an exhaust hood to be used as the storage and shipping point of chemical containers in Building 55. A 1,000 dscfm fume scrubber manufactured by Harrison is installed to control chemical vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104523
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104523
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104523
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104523
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
- the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The projected chemical emissions from the work area and scrubber system are 19.2 pounds per year of POCl_3 and 3.1 pounds per year of BBr_3 .
2. The chemical vapor exhaust scrubber must be on during the working hours and when damaged containers exist and escaping vapors are being controlled.
3. The maximum operating hours allowed shall be 24 hours per day, 365 days per year, for a total of 8,760 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104523
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

4. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of chemical losses due to leaks, container damage, spills, etc.
5. A record system on the amount and types of solvents purchased, reclaimed, recycled, lost due to container damage, etc., shall be required.
6. A meter to measure the pressure drop shall be installed on the scrubber system.
7. Objectionable odors shall not be allowed off plant property.
8. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all by chemicals purchased, reclaimed, recycled, lost due to damaged containers, etc.
9. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104523
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

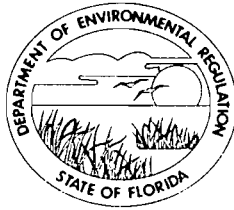
VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104524

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104524
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 4 South Exhaust
Scrubbers (2) for Gases
and Chemical Vapors

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors and cleaning operations in Building 4 South. Two 10,000 dscfm fume scrubber manufactured by Harrison are installed to control gases and chemical vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104524
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.
2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.
3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.
4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.
5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104524
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104524
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104524
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 79.7 pounds per year.
2. The potential acid vapor emissions from the work stations and scrubber system is 7.0 pounds per year.
3. The gas and VOC/solvent/acid vapor exhaust scrubbers must be on during the working hours.
4. The maximum operating hours allowed shall be 24 hours per day, 365 days per year, for a total of 8,760 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104524
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

5. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
6. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
7. A meter to measure the pressure drop shall be installed on each scrubber system.
8. Objectionable odors shall not be allowed off plant property.
9. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
10. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104524
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104525

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR

VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104525
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 4 North Exhaust
Scrubbers (2) for Gases
and Chemical Vapors

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the manufacture of semiconductors and cleaning operations in Building 4 North. Two 10,000 dscfm fume scrubber manufactured by Harrison are installed to control gases and chemical vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104525
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104525
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104525
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104525
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
- the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 4.4 pounds per year.
2. The potential acid vapor emissions from the work stations and scrubber system is 4.4 pounds per year.
3. The gas and VOC/solvent/acid vapor exhaust scrubbers must be on during the working hours.
4. The maximum operating hours allowed shall be 24 hours per day, 365 days per year, for a total of 8,760 hours per year.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104525
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

5. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
6. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
7. A meter to measure the pressure drop shall be installed on each scrubber system.
8. Objectionable odors shall not be allowed off plant property.
9. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
10. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104525
Expiration Date: June 30, 1986

SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

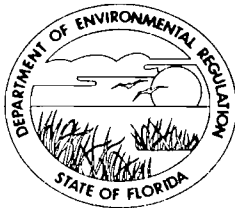
VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.

AC 05-104527

STATE OF FLORIDA
DEPARTMENT OF ENVIRONMENTAL REGULATION

TWIN TOWERS OFFICE BUILDING
2600 BLAIR STONE ROAD
TALLAHASSEE, FLORIDA 32301-8241



BOB GRAHAM
GOVERNOR
VICTORIA J. TSCHINKEL
SECRETARY

PERMITTEE:
Harris Semiconductor
P. O. Box 883
Melbourne, Florida 32901

Permit Number: AC 05-104527
Expiration Date: June 30, 1986
County: Brevard
Latitude/Longitude: 28° 01' 20" N/
80° 36' 10" W
Project: Building 58 Annex
VOC/Solvent Vapor
Exhaust Scrubber

This permit is issued under the provisions of Chapter 403, Florida Statutes, and Florida Administrative Code Rule(s) 17-2 and 17-4. The above named permittee is hereby authorized to perform the work or operate the facility shown on the application and approved drawing(s), plans, and other documents attached hereto or on file with the department and made a part hereof and specifically described as follows:

For the permitting of hood type work stations for the testing and inspecting of semiconductors in Building 58 Annex. A 3,000 dscfm fume scrubber manufactured by Harrison is installed to control VOC/solvent vapors at the applicant's existing facility located on Palm Bay Road. The UTM coordinates are Zone 17-538.7 km East and 3100.9 km North.

The source shall be in accordance with the permit application and plans, documents, amendments, and drawings except as otherwise noted on pages 5-7, Specific Conditions.

Attachments are as follows:

1. Application to Construct Air Pollution Sources, DER Form 17-1.202(1), and Mr. James R. Kolanek's cover letter dated May 21, 1985.
2. Mr. James R. Kolanek's letter with Attachment dated June 12, 1985.
3. Mr. C. H. Fancy's letter dated June 21, 1985.
4. Mr. James R. Kolanek's letter with Attachments dated August 21, 1985.

PERMITTEE:
Harris Semiconductor

Permit Number: AC 05-104527
Expiration Date: June 30, 1986

GENERAL CONDITIONS:

1. The terms, conditions, requirements, limitations, and restrictions set forth herein are "Permit Conditions" and as such are binding upon the permittee and enforceable pursuant to the authority of Sections 403.161, 403.727, or 403.859 through 403.861, Florida Statutes. The permittee is hereby placed on notice that the department will review this permit periodically and may initiate enforcement action for any violation of the "Permit Conditions" by the permittee, its agents, employees, servants or representatives.

2. This permit is valid only for the specific processes and operations applied for and indicated in the approved drawings or exhibits. Any unauthorized deviation from the approved drawings, exhibits, specifications, or conditions of this permit may constitute grounds for revocation and enforcement action by the department.

3. As provided in Subsections 403.087(6) and 403.722(5), Florida Statutes, the issuance of this permit does not convey any vested rights or any exclusive privileges. Nor does it authorize any injury to public or private property or any invasion of personal rights, nor any infringement of federal, state or local laws or regulations. This permit does not constitute a waiver of or approval of any other department permit that may be required for other aspects of the total project which are not addressed in the permit.

4. This permit conveys no title to land or water, does not constitute state recognition or acknowledgement of title, and does not constitute authority for the use of submerged lands unless herein provided and the necessary title or leasehold interests have been obtained from the state. Only the Trustees of the Internal Improvement Trust Fund may express state opinion as to title.

5. This permit does not relieve the permittee from liability for harm or injury to human health or welfare, animal, plant or aquatic life or property and penalties therefore caused by the construction or operation of this permitted source, nor does it allow the permittee to cause pollution in contravention of Florida Statutes and department rules, unless specifically authorized by an order from the department.

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6. The permittee shall at all times properly operate and maintain the facility and systems of treatment and control (and related appurtenances) that are installed or used by the permittee to achieve compliance with the conditions of this permit, as required by department rules. This provision includes the operation of backup or auxiliary facilities or similar systems when necessary to achieve compliance with the conditions of the permit and when required by department rules.

7. The permittee, by accepting this permit, specifically agrees to allow authorized department personnel, upon presentation of credentials or other documents as may be required by law, access to the premises, at reasonable times, where the permitted activity is located or conducted for the purpose of:

- a. Having access to and copying any records that must be kept under the conditions of the permit;
- b. Inspecting the facility, equipment, practices, or operations regulated or required under this permit; and
- c. Sampling or monitoring any substances or parameters at any location reasonably necessary to assure compliance with this permit or department rules.

Reasonable time may depend on the nature of the concern being investigated.

8. If, for any reason, the permittee does not comply with or will be unable to comply with any condition or limitation specified in this permit, the permittee shall immediately notify and provide the department with the following information:

- a. a description of and cause of non-compliance; and
- b. the period of noncompliance, including exact dates and times; or, if not corrected, the anticipated time the noncompliance is expected to continue, and steps being taken to reduce, eliminate, and prevent recurrence of the noncompliance.

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The permittee shall be responsible for any and all damages which may result and may be subject to enforcement action by the department for penalties or revocation of this permit.

9. In accepting this permit, the permittee understands and agrees that all records, notes, monitoring data and other information relating to the construction or operation of this permitted source, which are submitted to the department, may be used by the department as evidence in any enforcement case arising under the Florida Statutes or department rules, except where such use is proscribed by Sections 403.73 and 403.111, Florida Statutes.

10. The permittee agrees to comply with changes in department rules and Florida Statutes after a reasonable time for compliance, provided however, the permittee does not waive any other rights granted by Florida Statutes or department rules.

11. This permit is transferable only upon department approval in accordance with Florida Administrative Code Rules 17-4.12 and 17-30.30, as applicable. The permittee shall be liable for any non-compliance of the permitted activity until the transfer is approved by the department.

12. This permit is required to be kept at the work site of the permitted activity during the entire period of construction or operation.

13. This permit also constitutes:

- () Determination of Best Available Control Technology (BACT)
- () Determination of Prevention of Significant Deterioration (PSD).
- () Compliance with New Source Performance Standards.

14. The permittee shall comply with the following monitoring and record keeping requirements:

- a. Upon request, the permittee shall furnish all records and plans required under department rules. The retention period for all records will be extended automatically, unless otherwise stipulated by the department, during the course of any unresolved enforcement action.

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- b. The permittee shall retain at the facility or other location designated by this permit records of all monitoring information (including all calibration and maintenance records and all original strip chart recordings for continuous monitoring instrumentation), copies of all reports required by this permit, and records of all data used to complete the application for this permit. The time period of retention shall be at least three years from the date of the sample, measurement, report or application unless otherwise specified by department rule.
- c. Records of monitoring information shall include:
 - the date, exact place, and time of sampling or measurements;
 - the person responsible for performing the sampling or measurements;
 - the date(s) analyses were performed;
 - the person responsible for performing the analyses;
 - the analytical techniques or methods used; and
 - the results of such analyses.

15. When requested by the department, the permittee shall within a reasonable time furnish any information required by law which is needed to determine compliance with the permit. If the permittee becomes aware that relevant facts were not submitted or were incorrect in the permit application or in any report to the department, such facts or information shall be submitted or corrected promptly.

SPECIFIC CONDITIONS:

1. The maximum allowable VOC (volatile organic compounds)/solvent emissions from the work stations and scrubber system shall be 4.2 pounds per year.
2. The VOC/solvent vapor exhaust scrubber must be on during the working hours.
3. The maximum operating hours allowed shall be 8 hours per day, 264 days per year, for a total of 2,112 hours per year.

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4. An inspection and maintenance plan shall be submitted to the DER's St. Johns River District office as part of the operating permit application. The plan shall include provisions for the prevention and correction of VOC/solvent losses from leaks and equipment malfunction and a record system on the amount and types of VOC/solvents purchased and reclaimed.
5. Compliance with the VOC/solvent emissions limit for the working stations and the scrubber system shall be determined through the use of a material balance of the VOC/solvents purchased and reclaimed.
6. A meter to measure the pressure drop shall be installed on the scrubber system.
7. Objectionable odors shall not be allowed off plant property.
8. Annual reports, kept by month, shall be due 15 days after the anniversary date of the operating permit and are to be submitted to the DER's St. Johns River District office. The annual reports are to contain the amounts of all VOC/solvents by chemical, purchased and reclaimed.
9. The construction shall reasonably conform to the plans and schedule submitted in the application. If the applicant is unable to complete construction on schedule, he must notify the Department in writing 60 days prior to the expiration of the construction permit and submit a new schedule and request for an extension of the construction permit. (FAC Rule 17-4.09)
To obtain a permit to operate, the applicant must demonstrate compliance with the conditions of the construction permit and submit a complete application for an operating permit, including the application fee, along with compliance test results and Certificate of Completion, to the Department's St. Johns River District office 90 days prior to the expiration date of the construction permit. The permittee may continue to operate in compliance with all terms of the construction permit until its expiration date. Operation beyond the construction permit expiration date requires a valid permit to operate. (FAC Rules 17-4.22 and 17-4.23)
If the construction permit expires prior to the applicant requesting an extension or obtaining a permit to operate, then all activities at the project must cease and the applicant must apply for a new permit to construct which can take up to 90 days to process a complete application. (FAC Rule 17-4.10)

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SPECIFIC CONDITIONS:

Issued this _____ day of _____,
19__.

STATE OF FLORIDA DEPARTMENT
OF ENVIRONMENTAL REGULATION

VICTORIA J. TSCHINKEL, Secretary

_____ pages attached.